

# Hybrid III-V Silicon Quantum Dot and Quantum Well Lasers

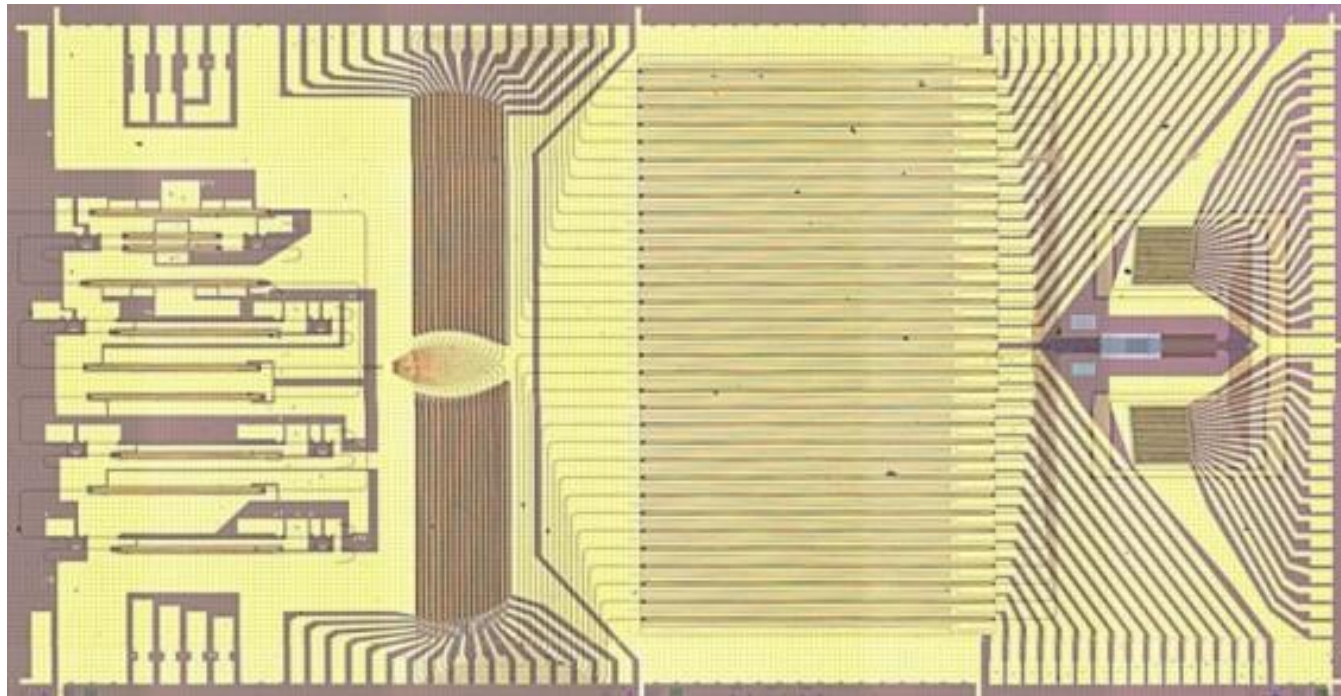
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John Bowers

Director, Institute for Energy Efficiency  
University of California, Santa Barbara

<http://optoelectronics.ece.ucsb.edu/>

**UCSB:** Jared Bauters, Daoxin Dai, Mike Davenport, Art Gossard, Martijn Heck,  
Jared Hulme, Alan Liu, Jon Peters, Daryl Spencer, Sudha Srinivasan



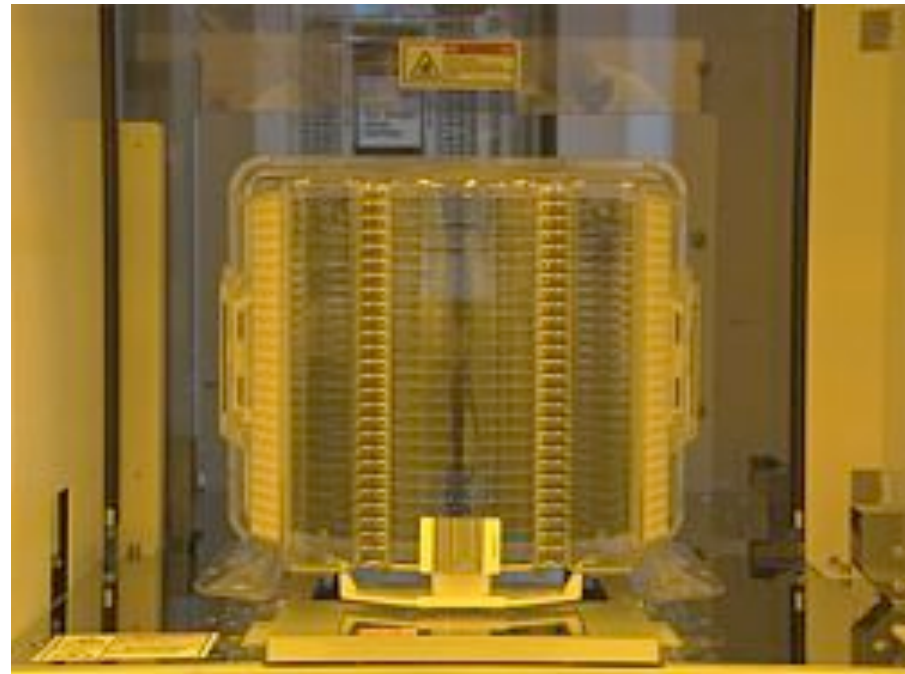
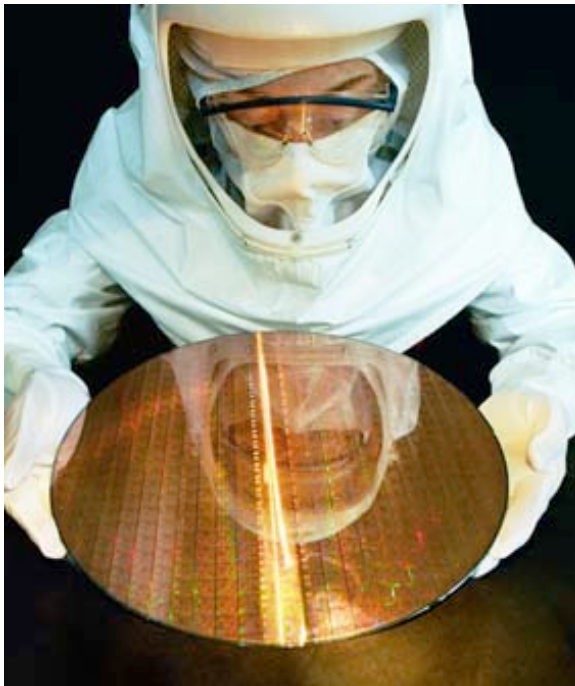
4 tunable lasers, 4x32 splitter, 32 amplifiers,  
32 phase shifters, 32 grating emitters, 32 photodetectors

Research supported by Josh Conway and Jag Shah at DARPA MTO

- Silicon Photonics
- Lasers on Silicon
  - Er doped
  - Patterned
  - Ge
  - Bonded
  - Epitaxially grown
- Quantum dot lasers
- Tunable Lasers
- Integration
- Commercialization
- Future
- Summary

# What is Silicon Photonics?

- Making photonic integrated circuits on Silicon using CMOS process technology in a CMOS fab
- Merging photonics and CMOS



The issue is not InP or GaAs versus Si. The issue is

- 1) Scaling photonics to high levels of integration with improved performance and better process control at low cost.
- 2) Solving electrical interconnect limits in Data centers, Supercomputers and ICs with higher capacity, lower cost optical interconnects

# 2014: Silicon Photonics Participants

Silicon Photonics  
Companies

Silicon &  
Systems Co's

Silicon  
Photonics  
Foundries

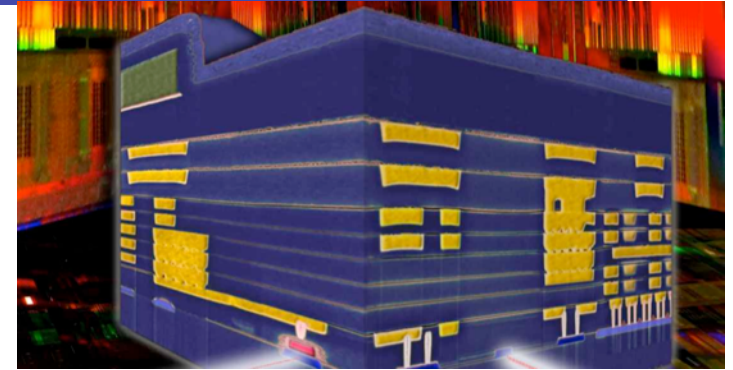
**This is not exhaustive list**

*Numerous Silicon Photonics Entrants  
Across Start-ups, Products, Foundries and Research*

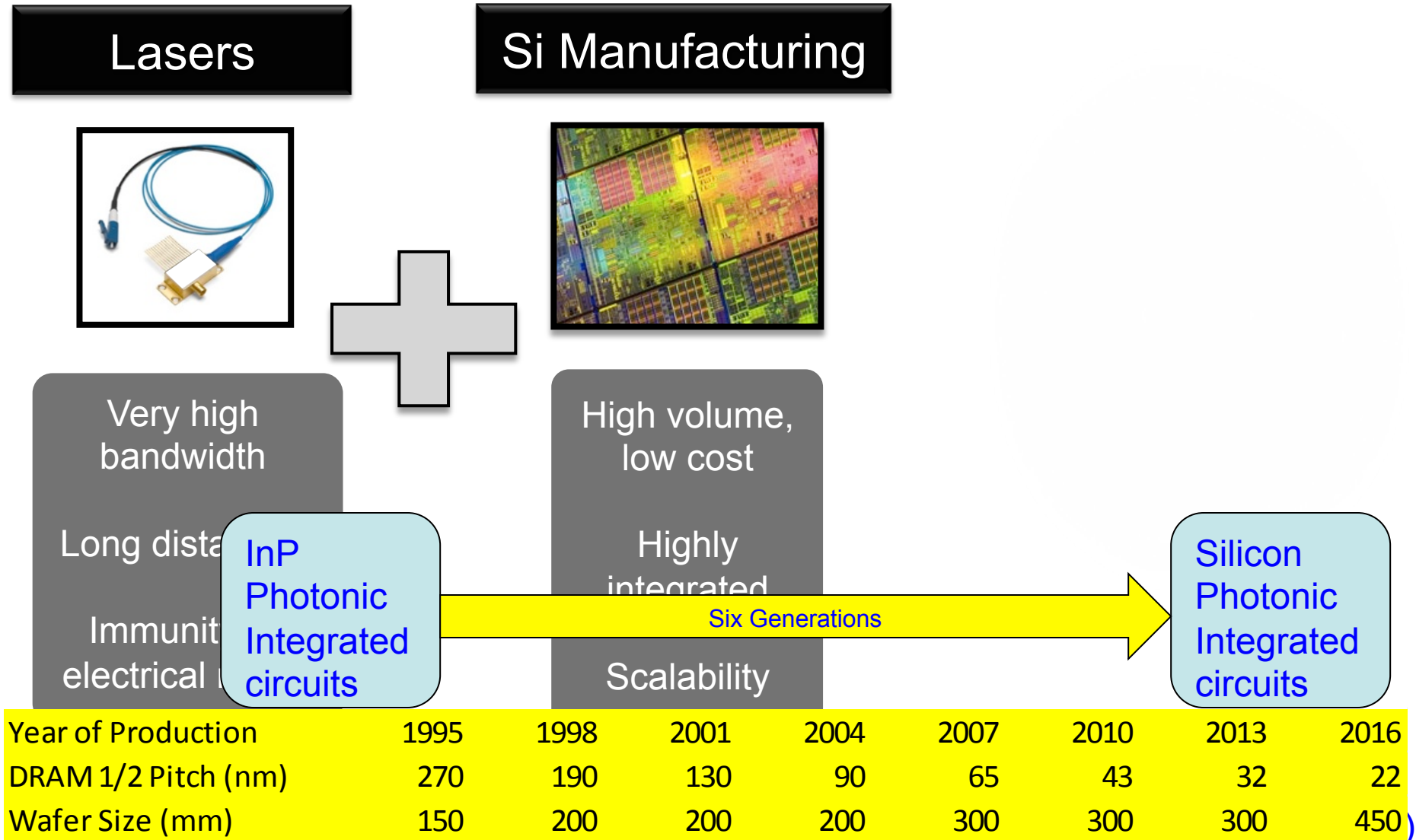





# Why Silicon Photonics?

- Integrate photonics with electronics
  - Same wafer
  - Bump bonding of silicon PIC with silicon IC
    - Same coefficient of thermal expansion
  - 3D stacking
- Reduce cost by going to larger diameter wafers (300 mm)
  - InP limited by wafer breakage to 100 mm diameter
- Reduce cost by sharing VLSI facility with electronics
- Improve yield by taking advantage of silicon process development
- Volume driver: Solve IC interconnect bottleneck (from 4 Tbps to 1 Pbps). Optical transmitters/receivers on processors, memories, switches.



*Cross-sectional view of an IBM Silicon Nanophotonics chip combining optical and electrical circuits  
Vlasov et al. IEDM postdeadline*



- What is needed is a photonics platform for interconnects and switching that is scalable to
  - Low power 
  - High capacity 
  - Low cost 
  - High volume
  - High yield
  - High reliability

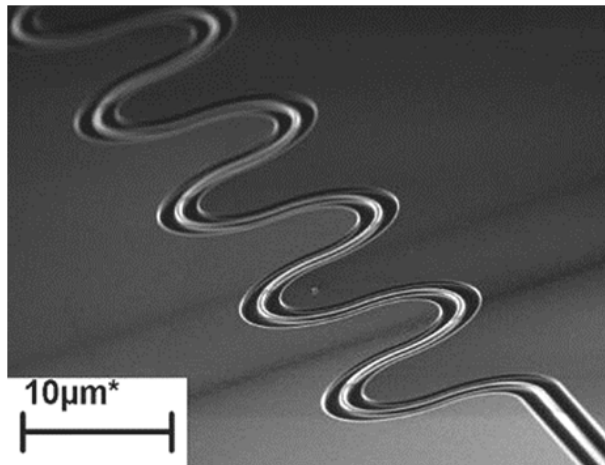
- Passives
  - Low loss waveguides
  - Splitters
  - Wavelength selective combiners/splitters
  - Isolators/Circulators
  - Comb generators
- Actives
  - Lasers (Pump and single frequency)
  - Modulators
  - Switches
  - Amplifiers
  - Photodetectors



# UCSB Superior Passive Si Photonic Devices

## Si/SiO<sub>2</sub> High index contrast:

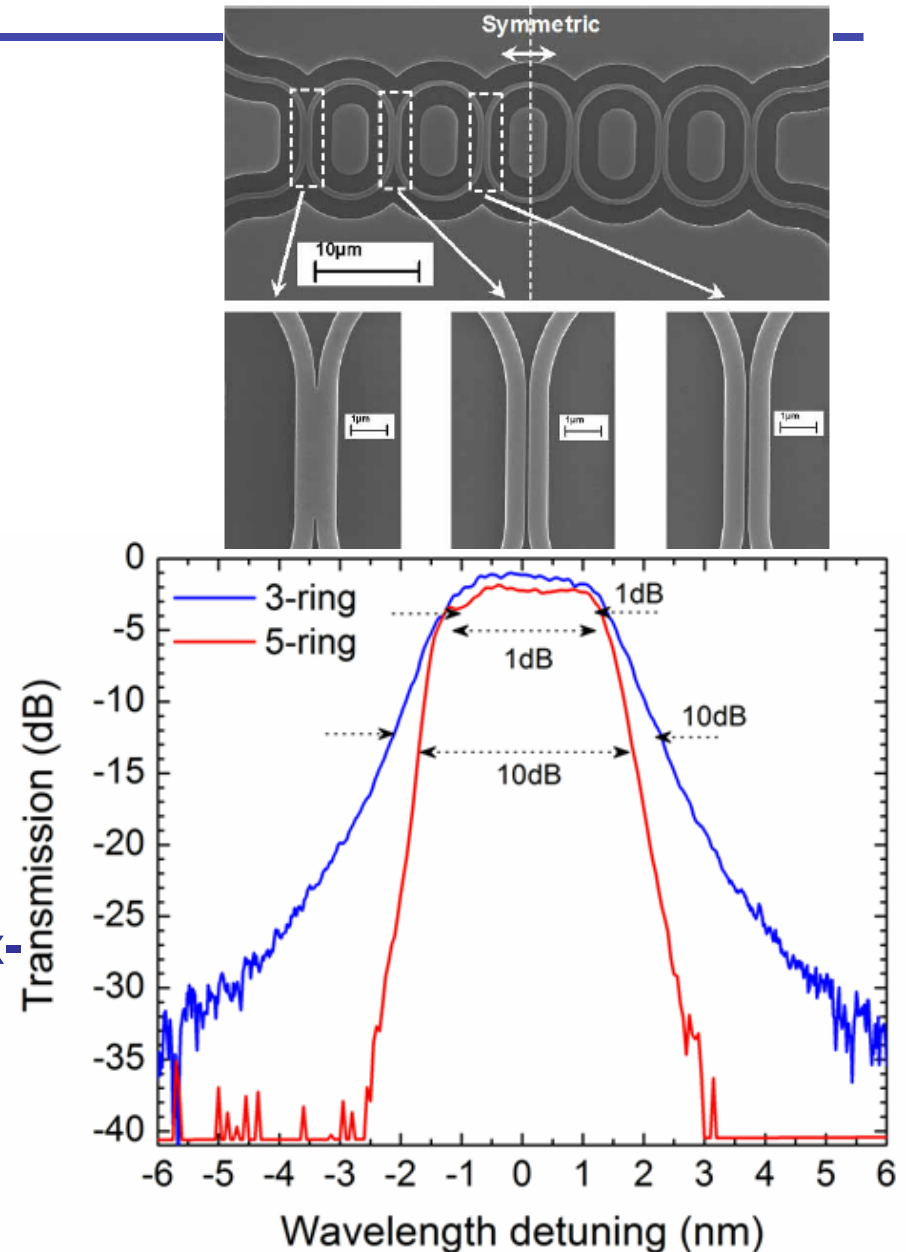
- Small wires
- Small passive devices
- High coupling loss
- High propagation loss



Example of losses for high-index-contrast “wire” waveguides:

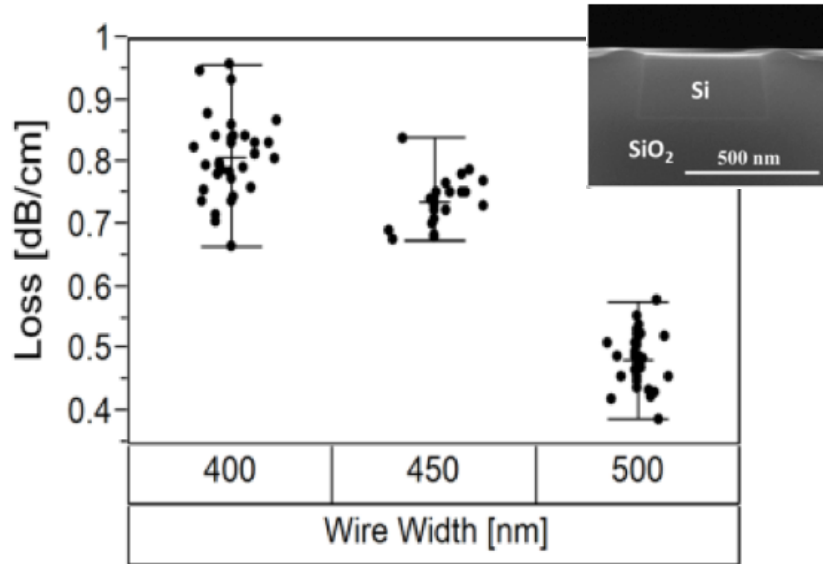
- For 6.5 mm radius bends, losses are 0.0043 dB per 180° turn

Source: Y. Vlasov, IBM



# Move to 193nm immersion lithography, 300mm wafers

## Lower loss waveguides



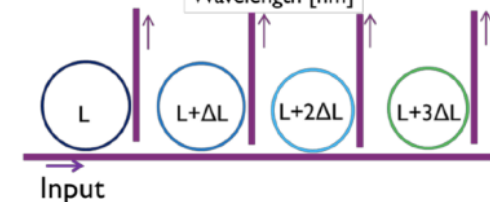
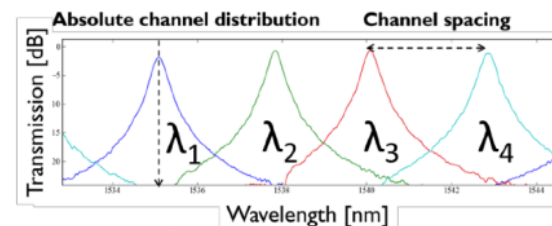
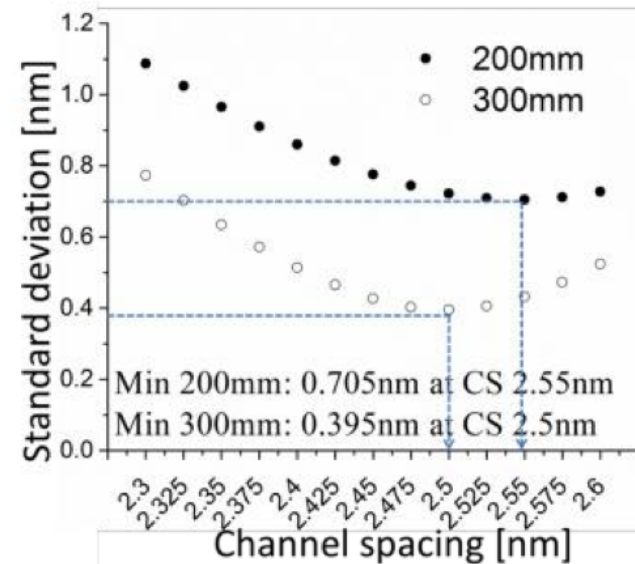
### Also:

- < 0.15dB/cm loss in ridge waveguides
- < 2dB/cm loss in slot waveguides

S. Selvaraja e.a., OFC '14

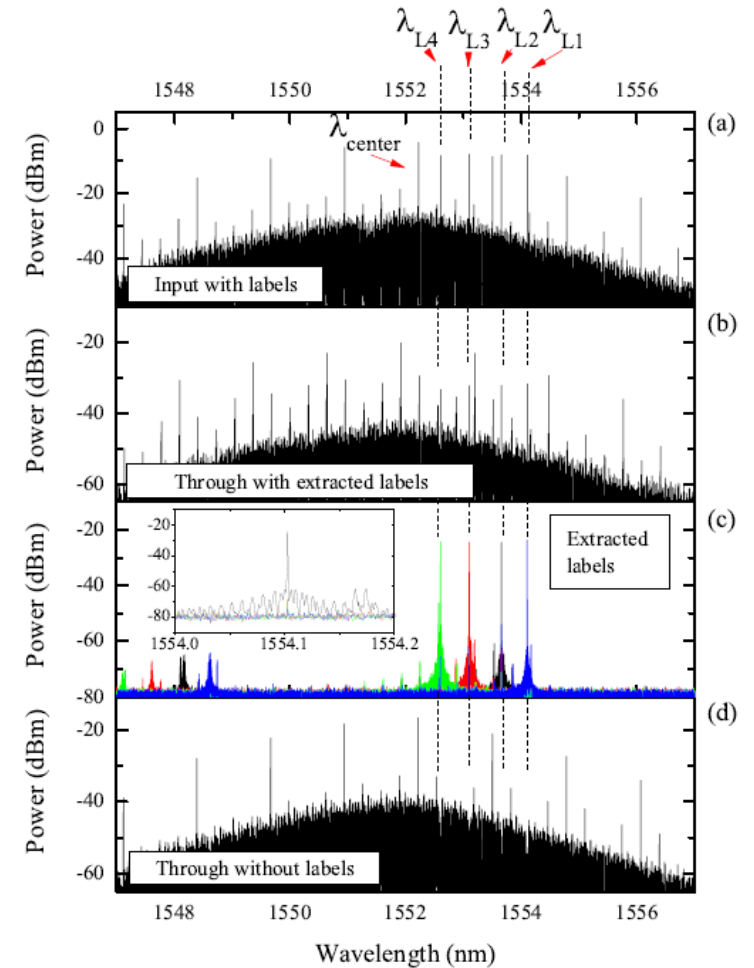
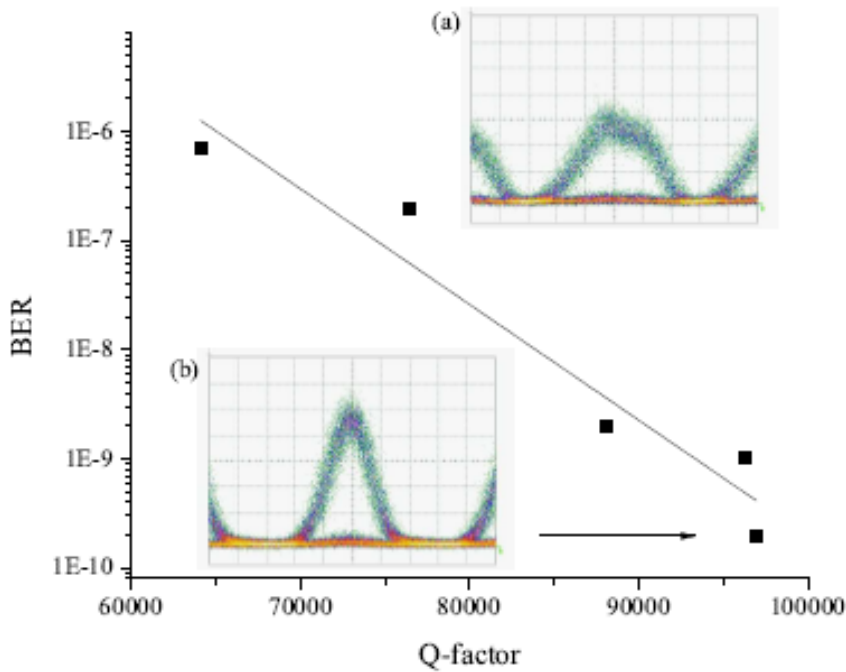
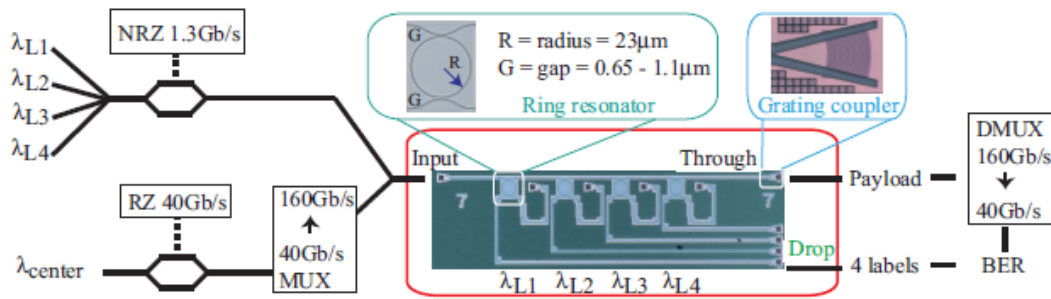
Selvaraja e.a. 17th OptoElectronics and Communications Conference (OECC 2012)

## More uniform channel spacing in ring demux



P. De Heyn, PhD Thesis UGent, May '14

# A four in-band label extractor for 160 Gb/s optical packets

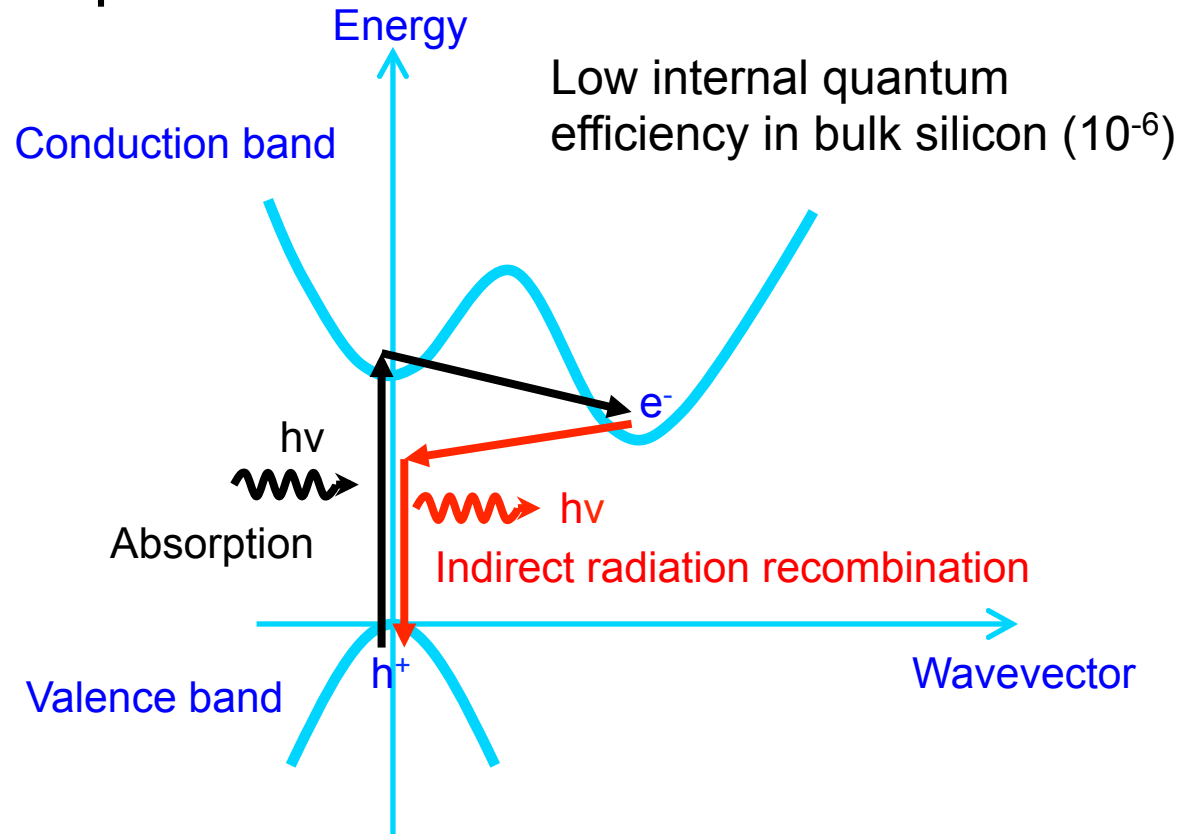


De Heyn e.a., IEEE JLT, 2014

- Passives
  - Low loss waveguides
  - Splitters
  - Wavelength selective combiners/splitters
  - Isolators/Circulators
  - Comb generators
- Actives
  - Lasers (Pump and single frequency)
  - Modulators
  - Switches
  - Amplifiers
  - Photodetectors

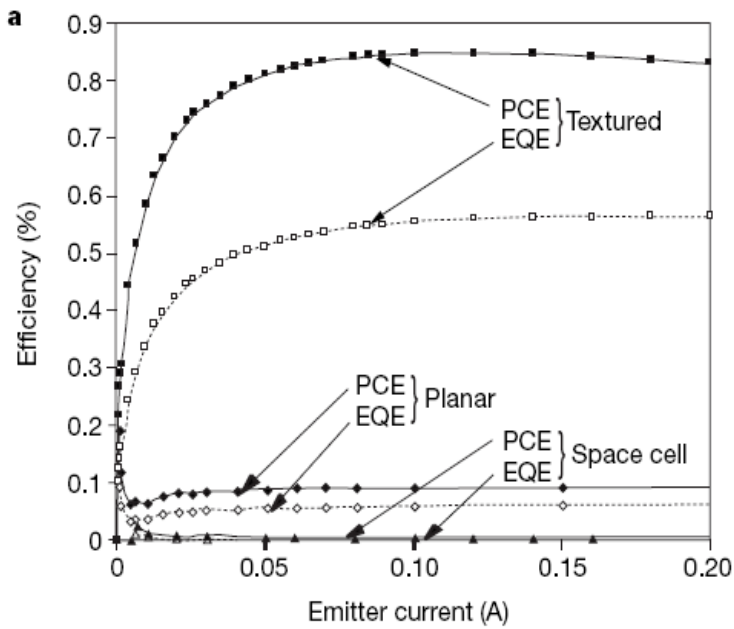
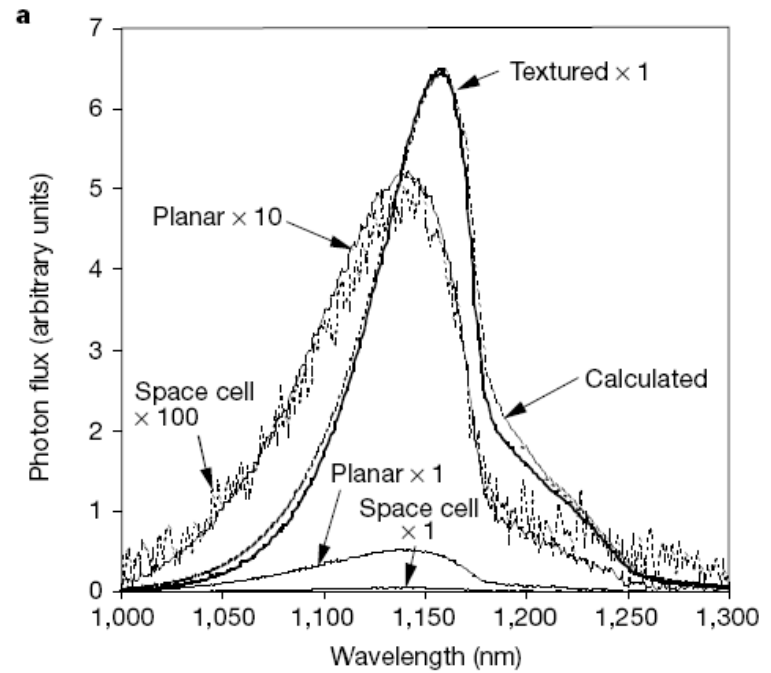
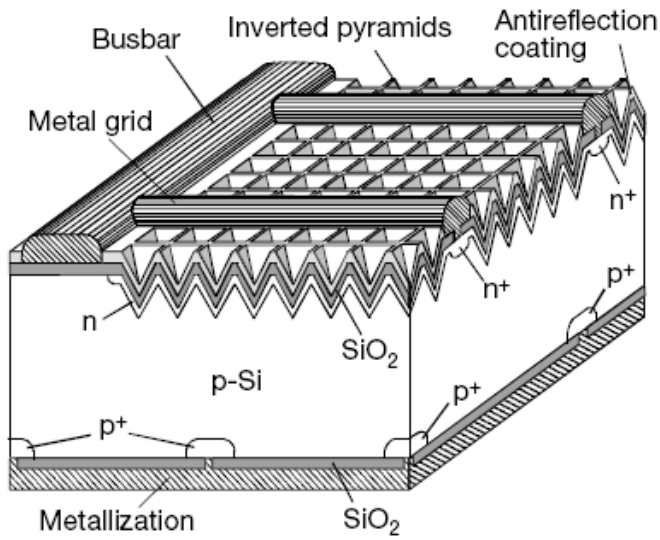
# Silicon light emission – limits

- Indirect band gap - inefficient for light emission
- Auger recombination
- Free carrier absorption



- Bulk silicon
- Low dimension Silicon
  - Silicon nanocrystal (Pavesi, ...)
  - Periodic nanopatterned crystalline silicon (Jimmy Xu)
- Er dopants (Dal Negro,....)
- Raman laser (Noda, Kyoto, UCLA, Intel)
- Another material for gain (hybrid approach)
  - Epitaxial
    - Ge
    - GeSn
    - Quantum Dot
    - Pillars
  - Bonding
    - Dice level
    - Wafer level (BCB or Molecular)

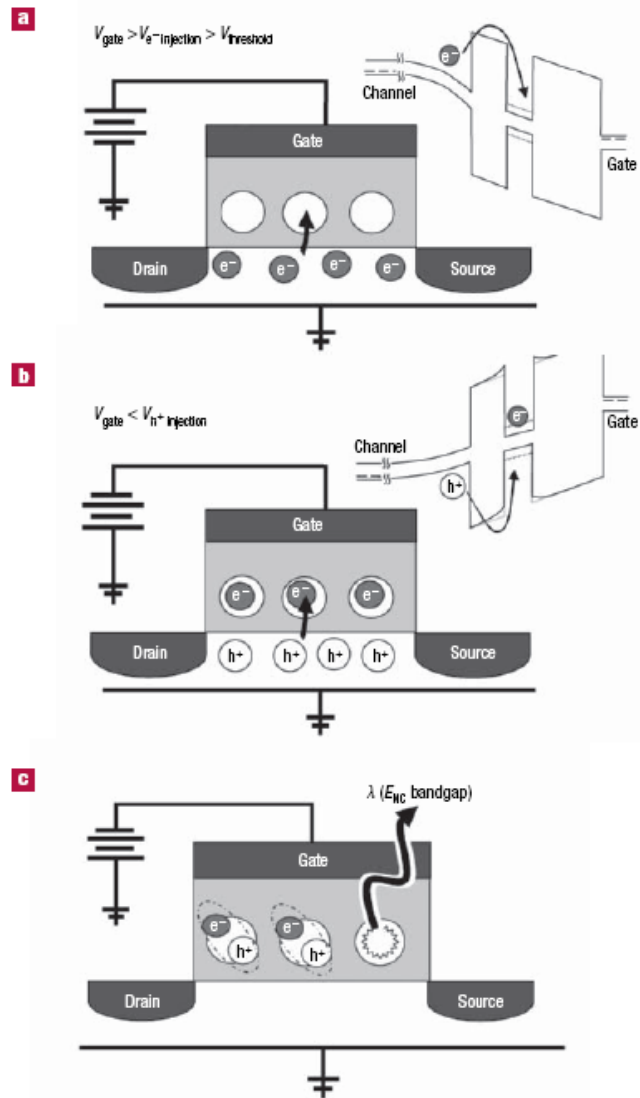
# Bulk silicon LED



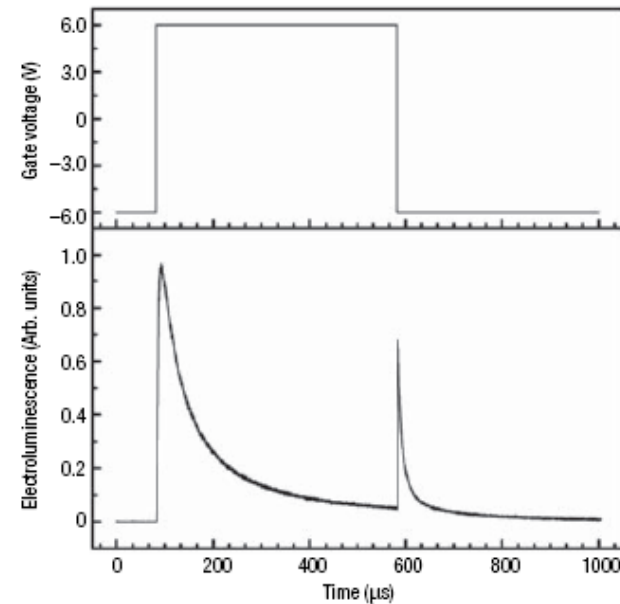
Solar cell forward bias  
 ~1% external quantum efficiency

M. A. Green et al., Nature 412, 805 (2001)

# UCSB Field effect electroluminescence

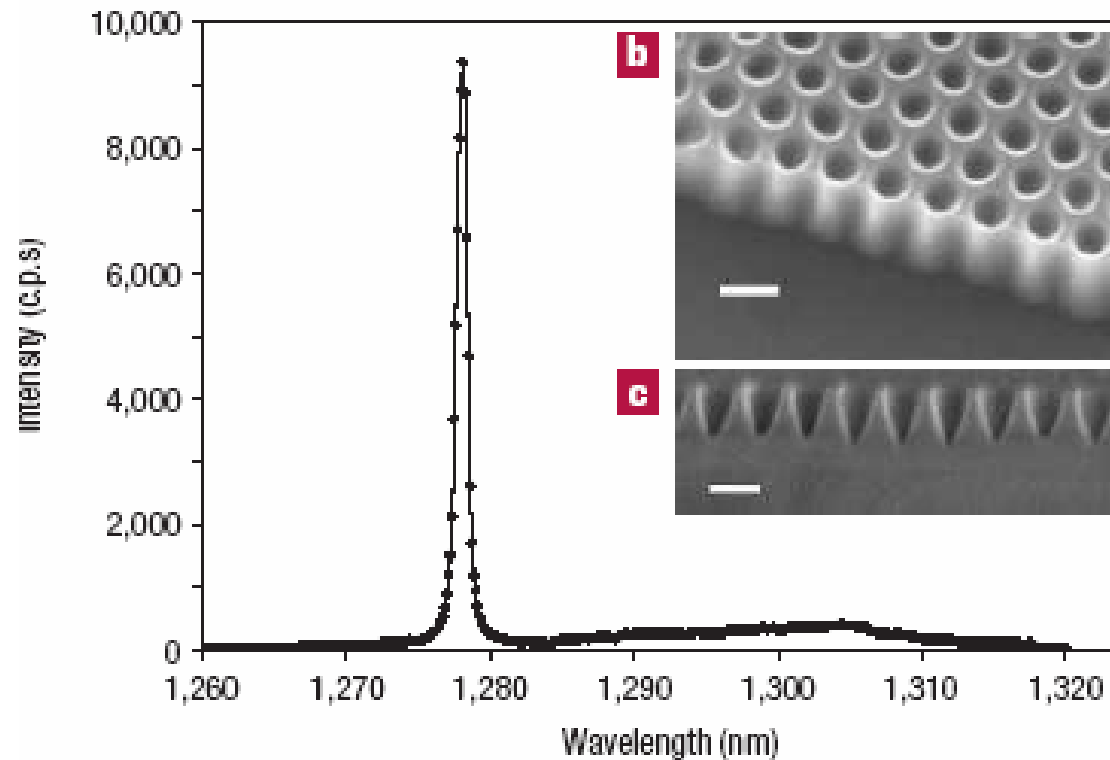


## Sequential injection of electron and hole

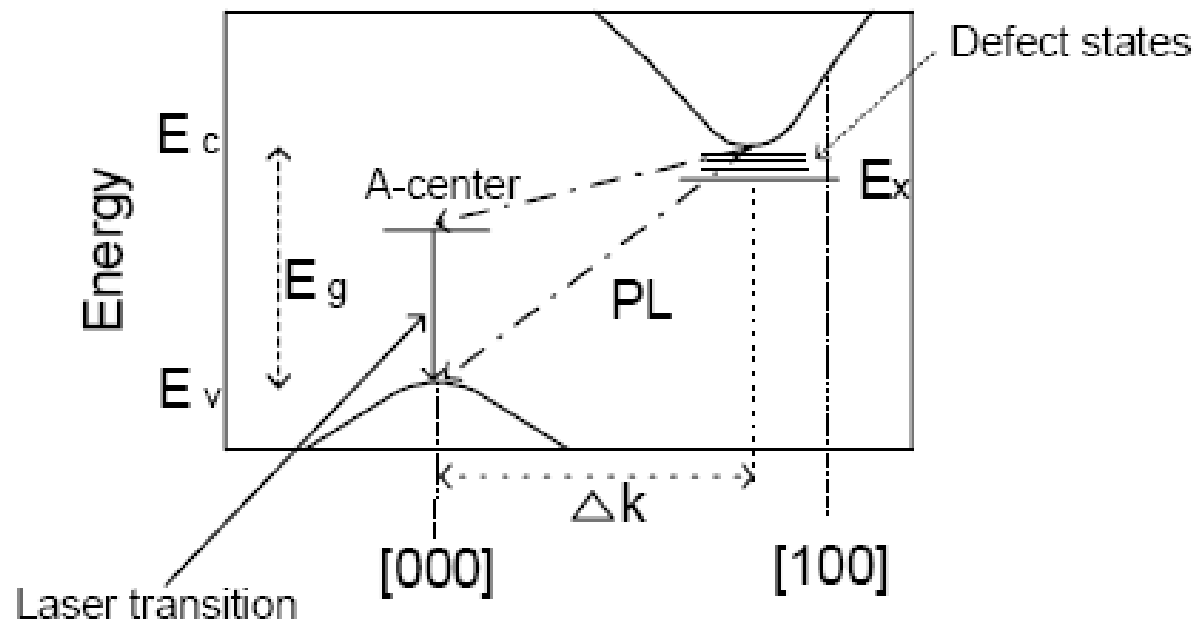


R. J. Walters, G. I. Bourianoff and H. A. Atwater, Nature Materials 4, 143 (2005)



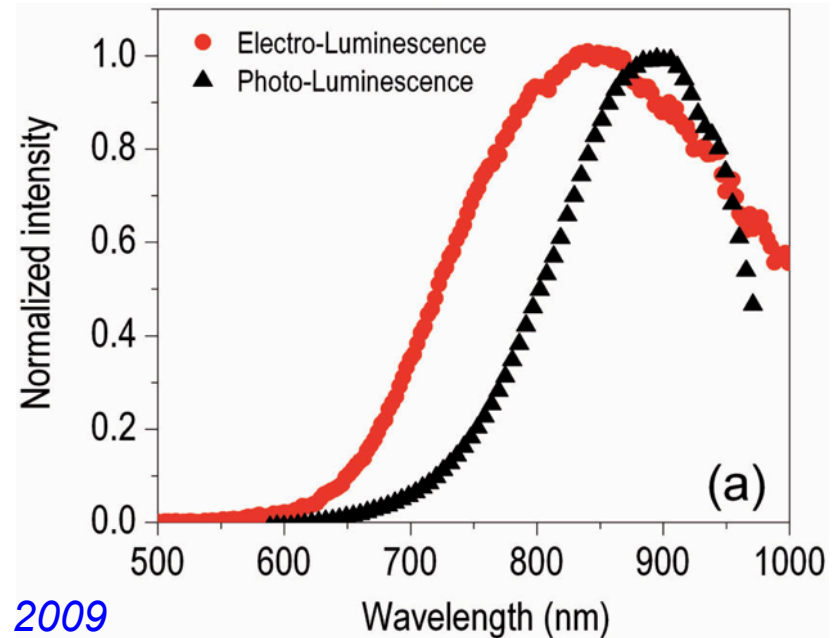
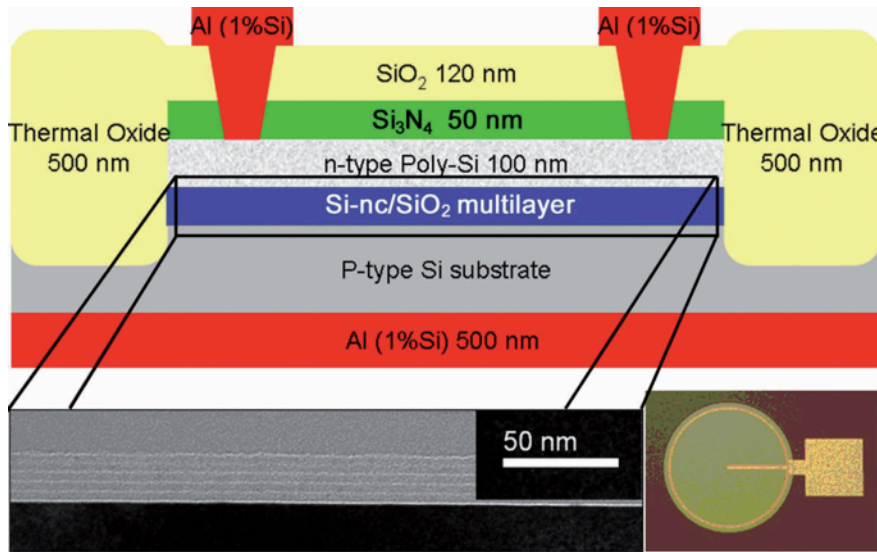


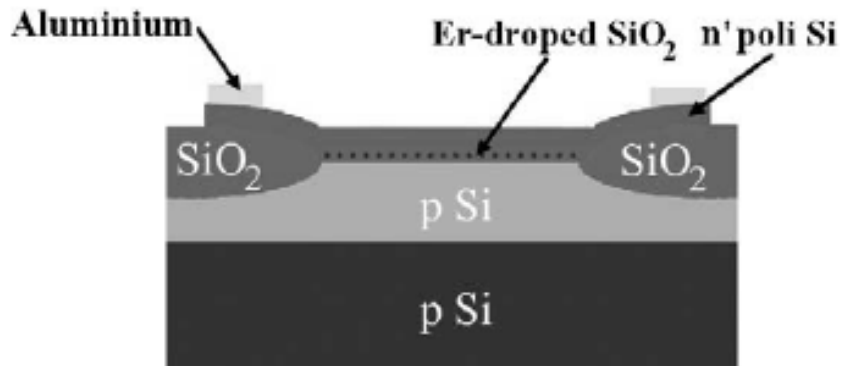
Nano-patterning creates a densely packed array of Emissive Structural Deformation (ESD) zones in the side-wall region of the nano-holes



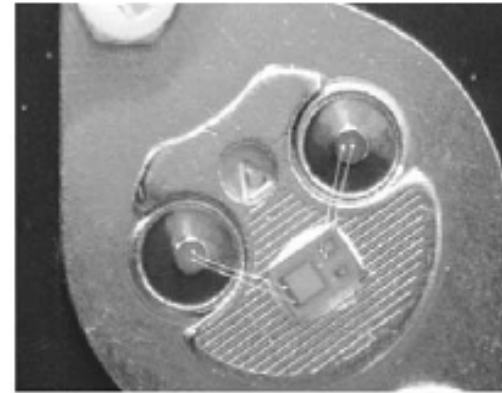
# Silicon nanoclusters: LED

- EL power efficiency values for LED devices:
  - 0.01–0.03% for pure Si-nc;
  - 0.2–0.3% for rare-earth ion doped
- For high EL efficiency: bipolar injection needed
  - issue: electron tunneling barrier  $\ll$  hole barrier





(a)



(b)

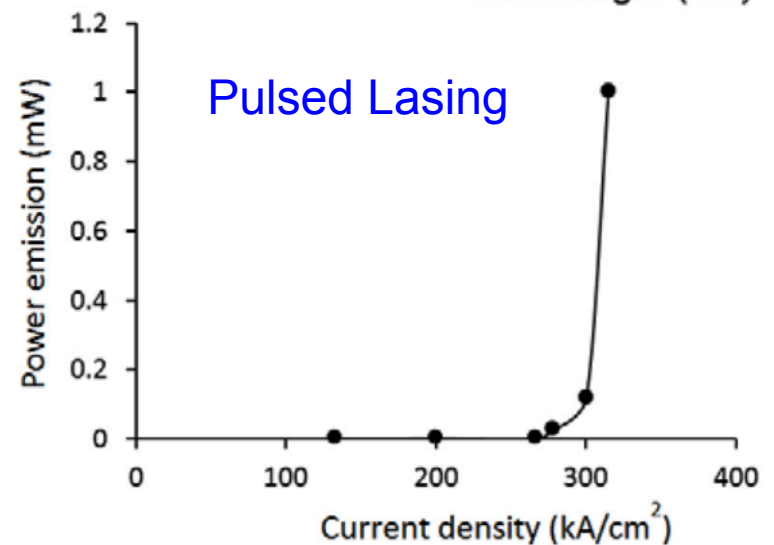
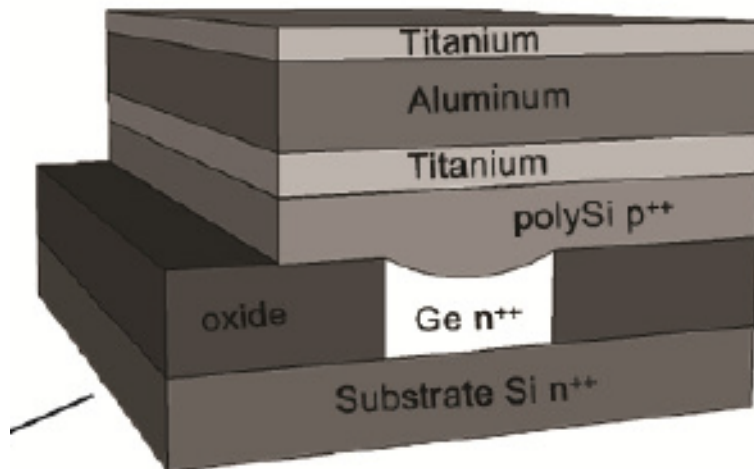
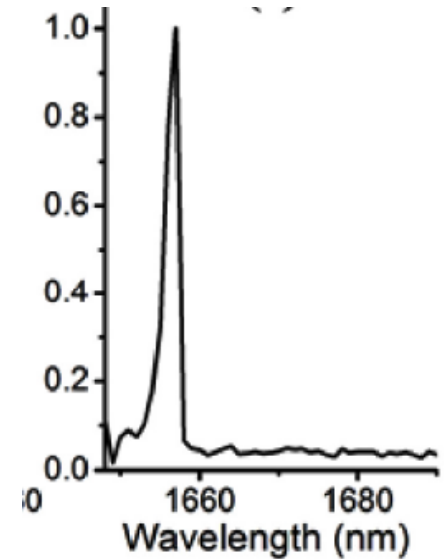
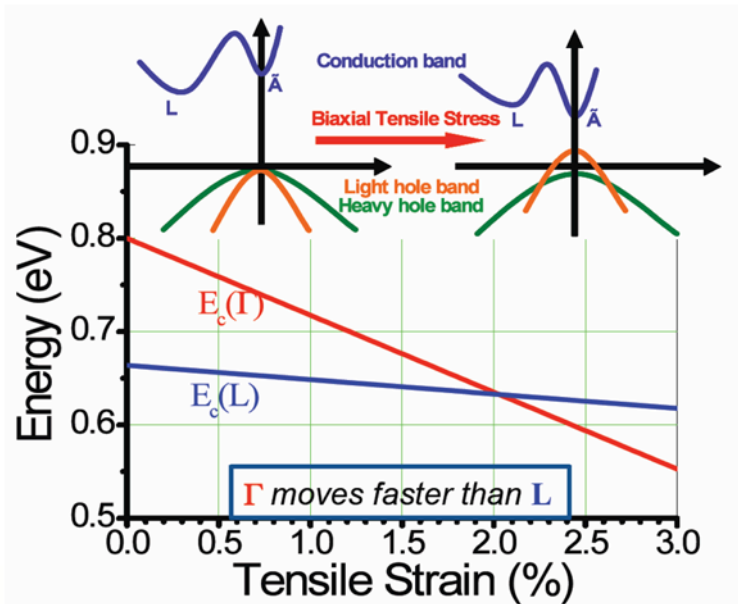
Table 1

Emission wavelength, cross-section and external quantum efficiency of MOS devices with rare-earth doped gate dielectric

Rare earth	$\lambda$ emission (nm)	$\sigma$ (cm <sup>2</sup> )	$\eta_{\text{ext}}$ (%)
Erbium	1540	$1 \times 10^{-14}$	10
Terbium	540	$4 \times 10^{-15}$	10
Ytterbium	980	$1 \times 10^{-15}$	0.1

# An electrically pumped germanium laser

Rodolfo E. Camacho-Aguilera,<sup>1</sup> Yan Cai,<sup>1</sup> Neil Patel,<sup>1</sup> Jonathan T. Bessette,<sup>1</sup> Marco Romagnoli,<sup>1,2</sup> Lionel C. Kimerling,<sup>1</sup> and Jurgen Michel<sup>1,\*</sup>



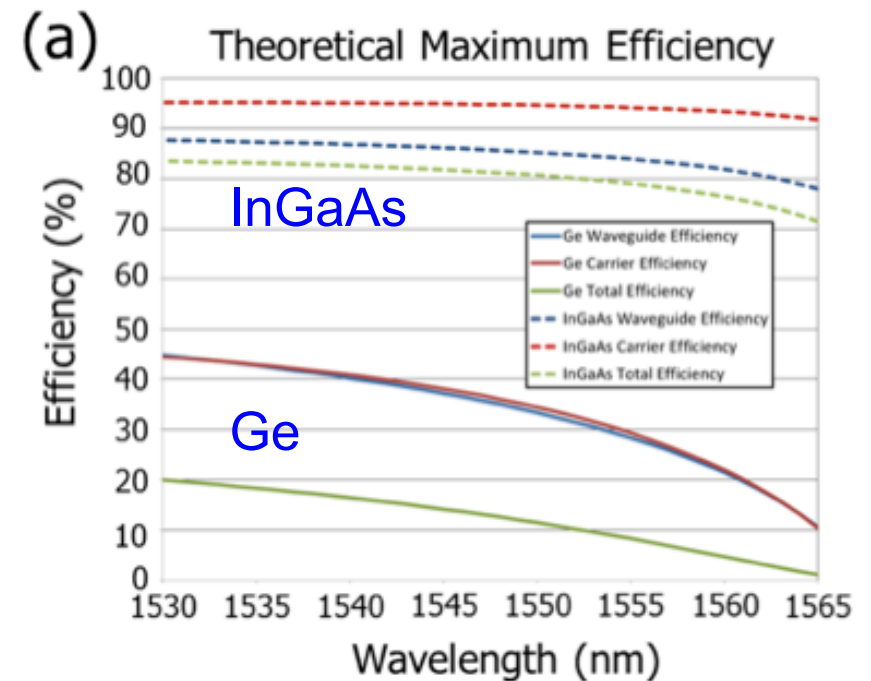
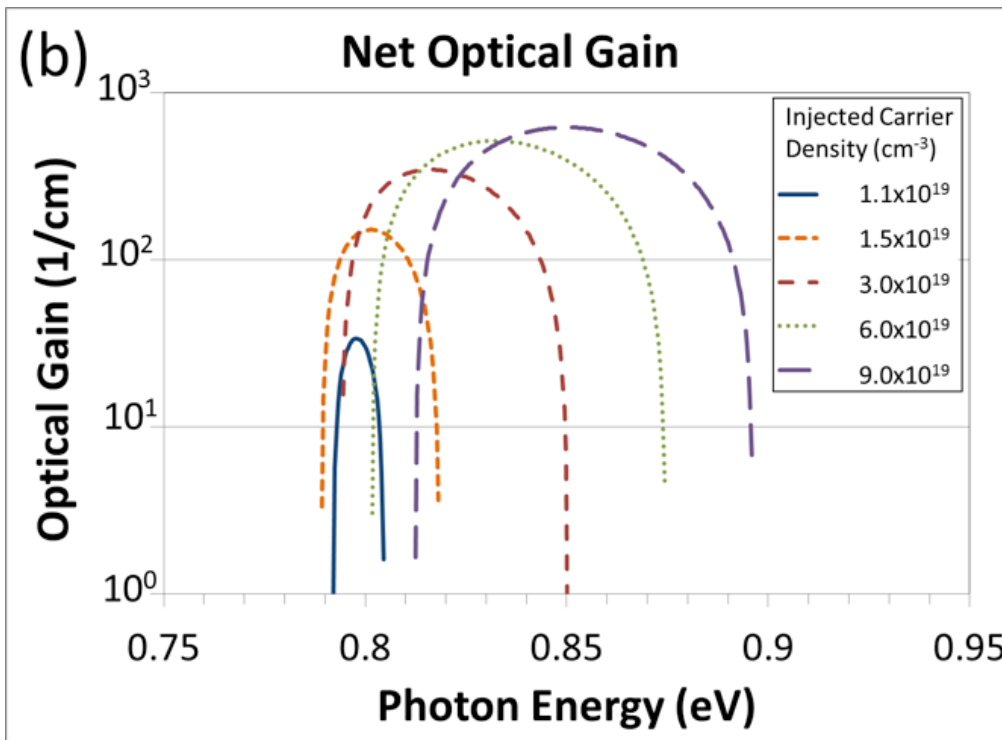
# Theoretical efficiency of electrically pumped, strained Ge lasers

David C. Nielsen,<sup>1,\*</sup> and J. Scott Rodgers,<sup>2,†</sup>

<sup>1</sup>Booz-Allen-Hamilton, 3811 N. Fairfax Dr. Arlington, VA, 22203, USA

<sup>2</sup>Defense Advanced Research Projects Agency, 675 N. Randolph St., Arlington, VA, 22203, USA

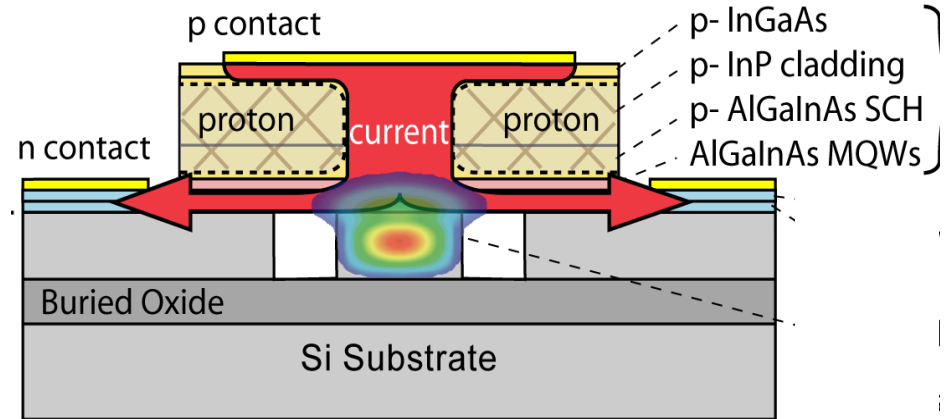
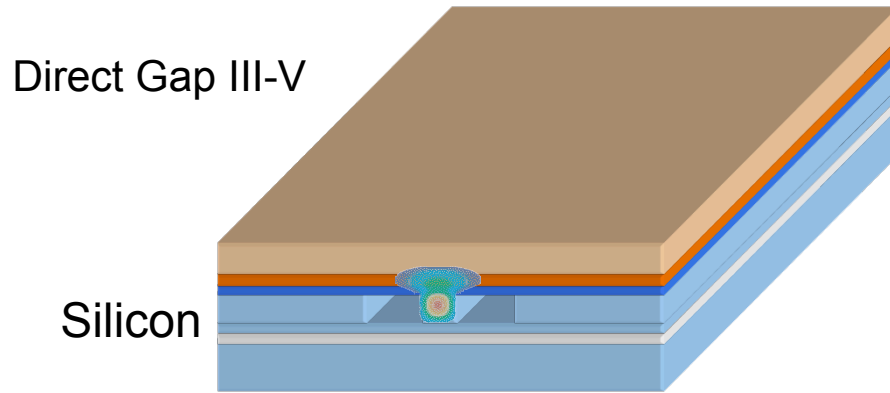
\*nielsen\_david@bah.com



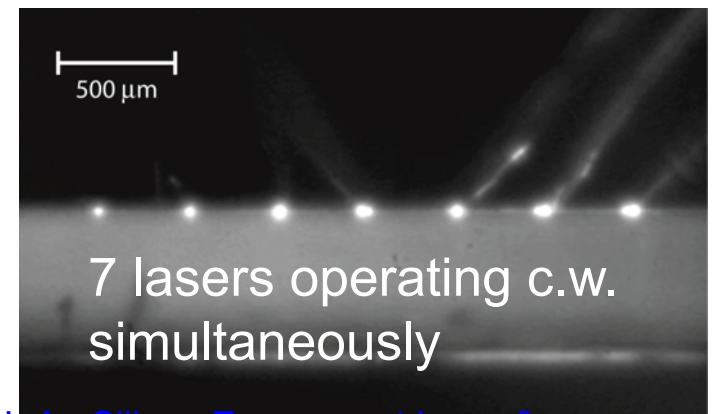
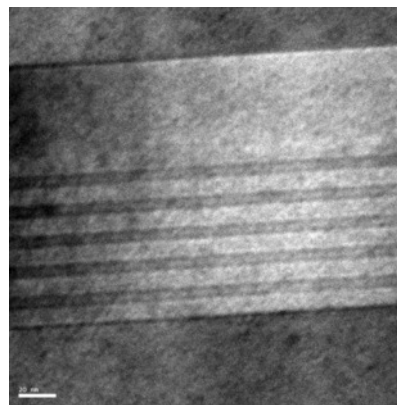
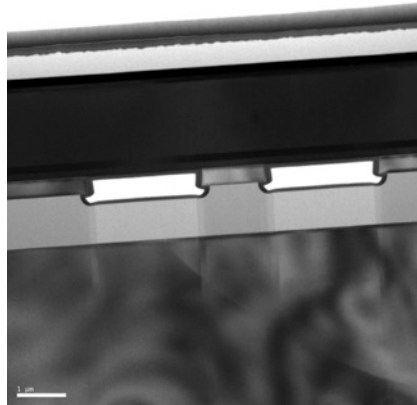
# Heterogeneous Integration

**Quantum Well** (UCSB, Ghent, Caltech,  
Tokyo Inst. Of Tech, Intel, HP, Aurrion)

**Quantum Dot** (Univ. Tokyo, UCSB)



- Optical gain from III-V Material
- Efficient coupling to silicon passive photonic devices
- No bonding **alignment** necessary: suitable for high volume CMOS
- All back end processing low temperature (<350 C)



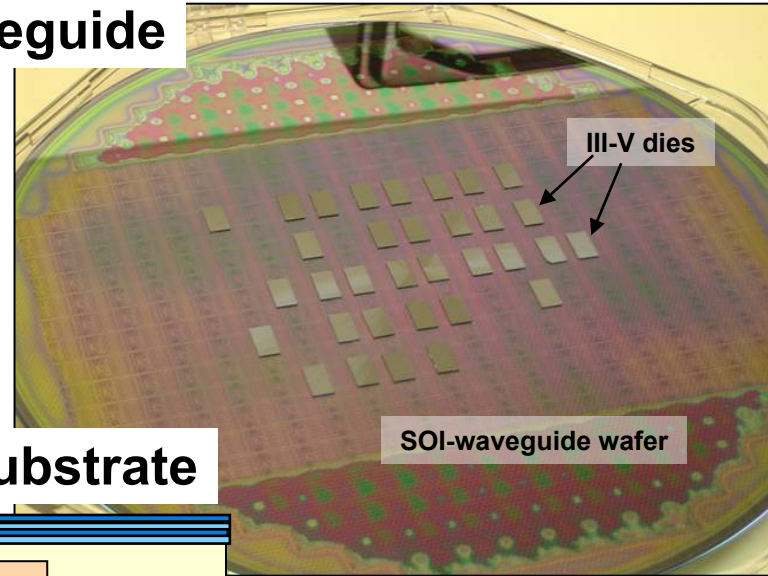
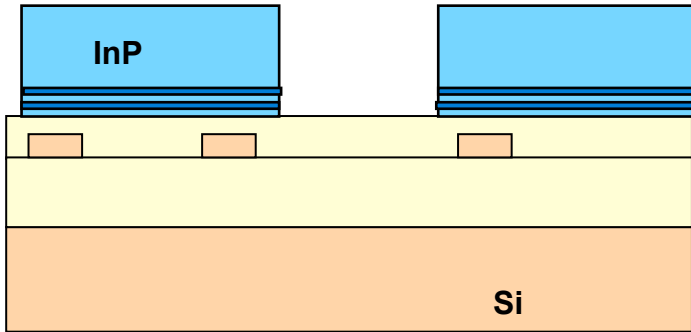
A.W. Fang, et al., "A Continuous Wave Hybrid AlGaInAs-Silicon Evanescent Laser," IEEE Photonics Technology Letters, 18 (10), 1143-1145, May 15, 2006



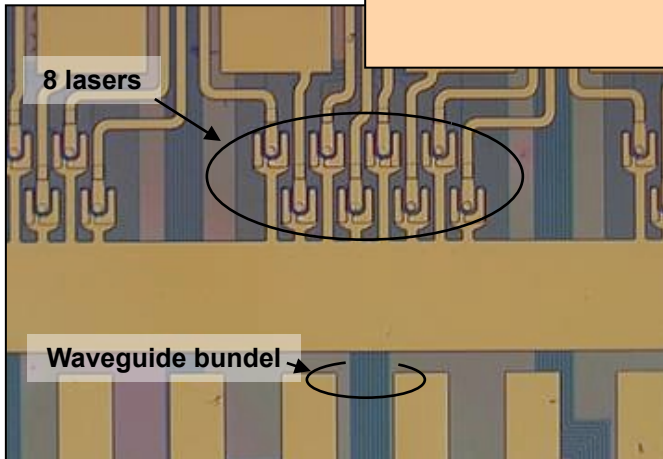
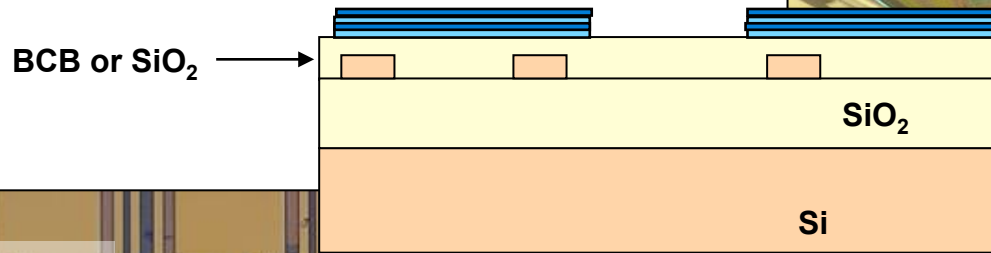
# Heterogeneous integration

UCSB, Intel, HP, Ghent, TIT, Caltech

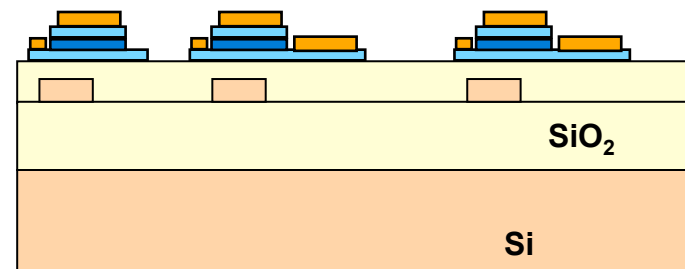
## Step 1: Bond InP-dies on SOI waveguide



## Step 2: Remove substrate



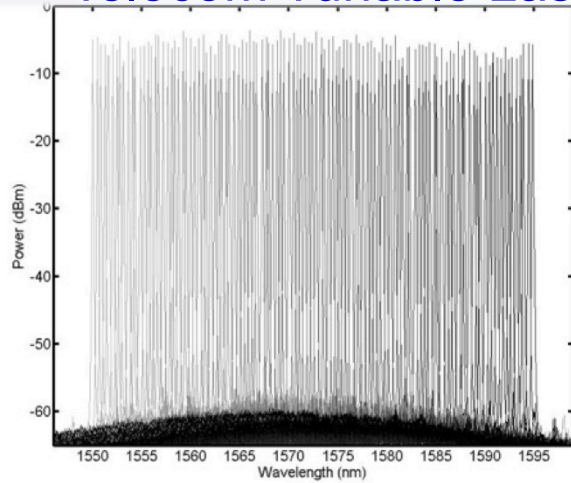
## Step 3: Process lasers at wafer scale



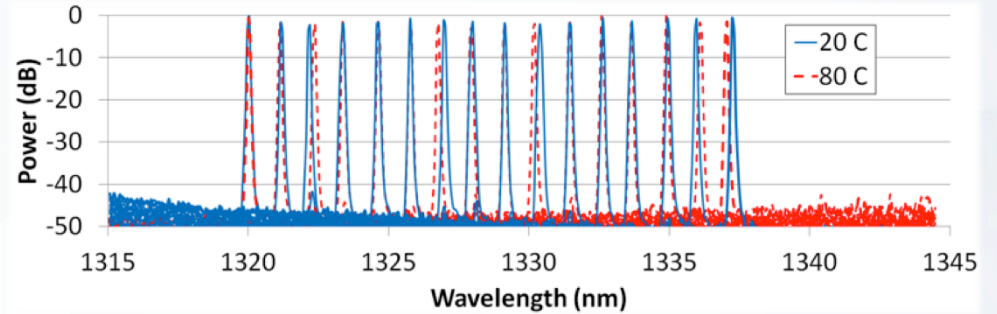
# Aurion PIC Integration

Brian Koch *et al.*, OFC Postdeadline 2013

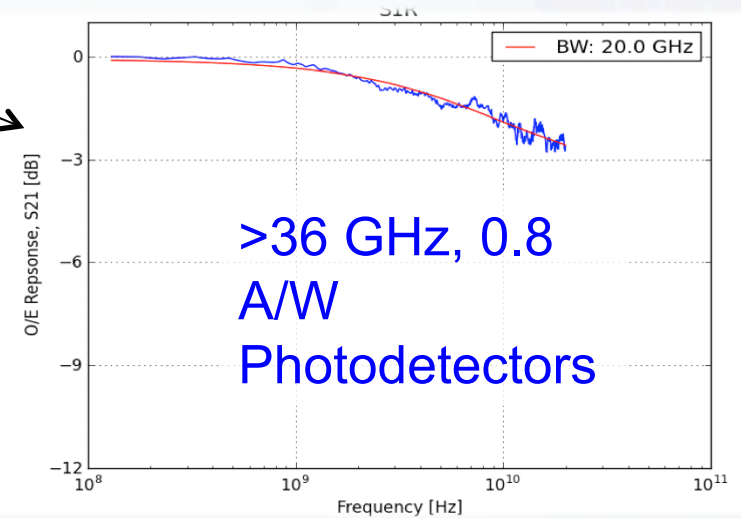
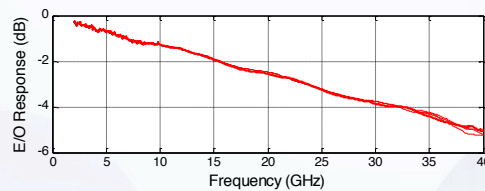
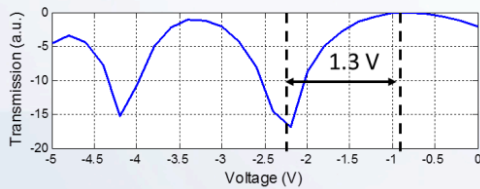
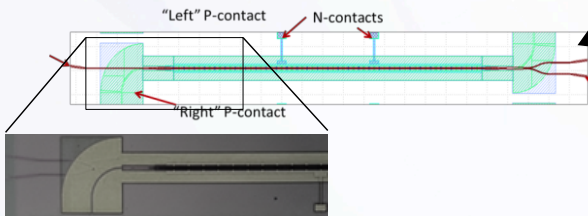
## Telecom Tunable Lasers



## Datacom uncooled WDM laser arrays



## Modulators: 23 GHz, >15 dB ER

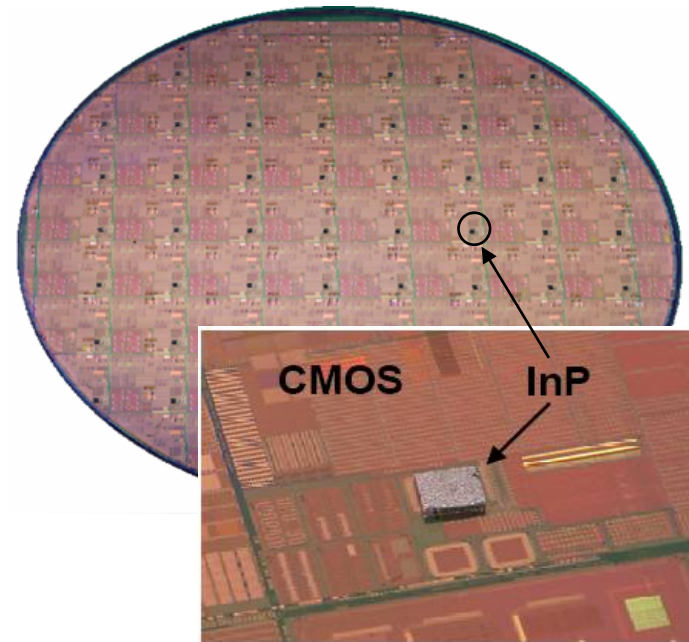
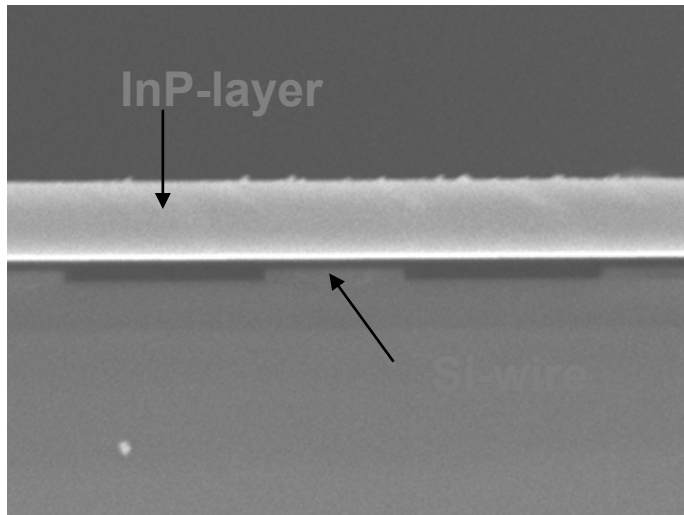


>36 GHz, 0.8  
A/W  
Photodetectors

# Heterogeneous integration

## Two alternatives for the die-to-wafer bonding process

- Adhesive layer bonding
  - Planarization and bonding in single step (IMEC-Ghent University)
  - Ultra-thin bonding layers (sub 200nm demonstrated) [1]
- Molecular bonding
  - InP on SOI-waveguides (UCSB, Intel, Hewlett Packard, Caltech, TIT, CEA-LETI, TRACIT) [2,3]



[1] G. Roelkens et al., "Adhesive Bonding of InP/InGaAsP Dies to Processed Silicon-On-Insulator Wafers using DVS-bis-Benzocyclobutene", J. Electrochem. Soc., Volume 153, Issue 12, pp. G1015-G1019 (2006)

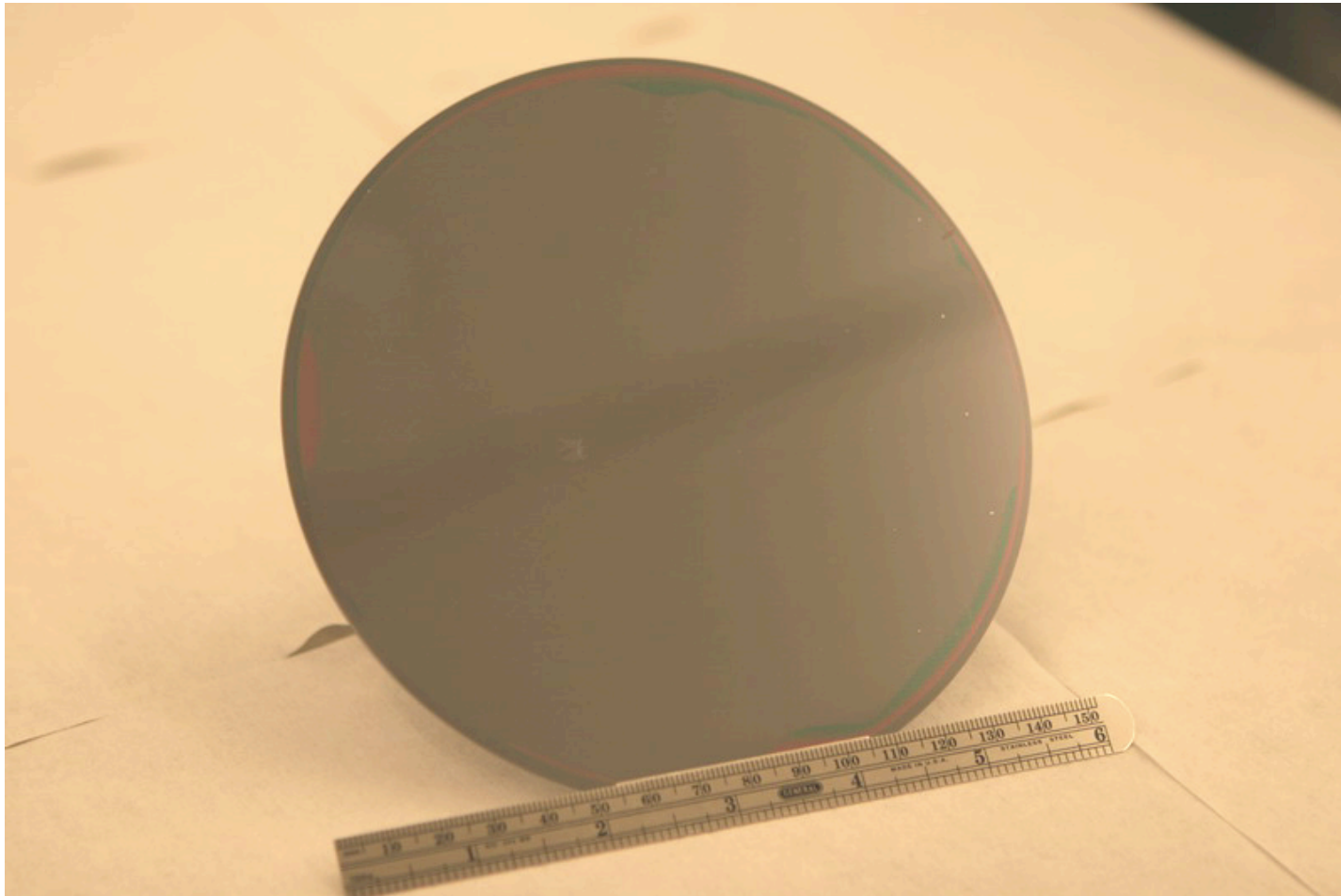
[2] D. Liang, G. Roelkens, R. Baets, J. E. Bowers, "Hybrid Integrated Platforms for Silicon Photonics," Materials, 3 (3), 1782-1802, March 12, 2010

[3] M. Kostrzewa et al., 'InP dies transferred onto silicon substrate for optical interconnects application', Sensors & Actuators A 125 (2006) 411-414

# UCSB Quantum Well Epi on 150 mm Silicon

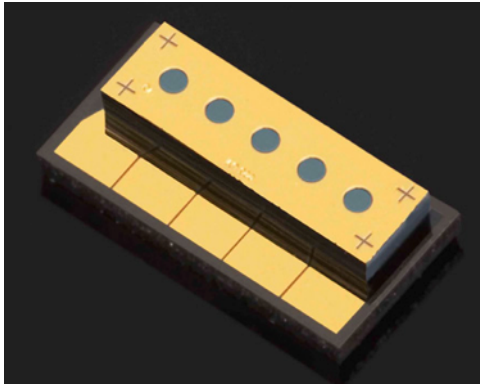
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## Oxygen Plasma Enhanced Molecular Bonding

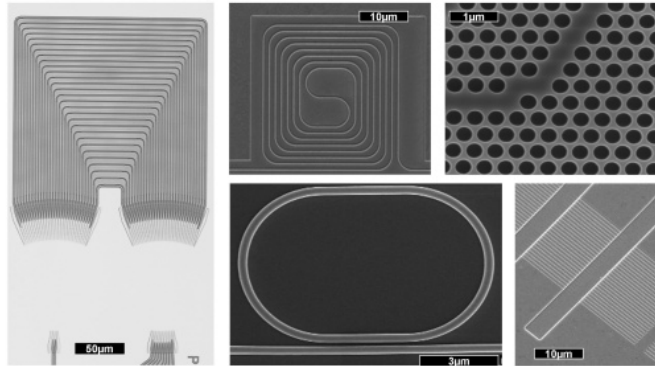


# Heterogeneous Integration of 6 Photonic Platforms

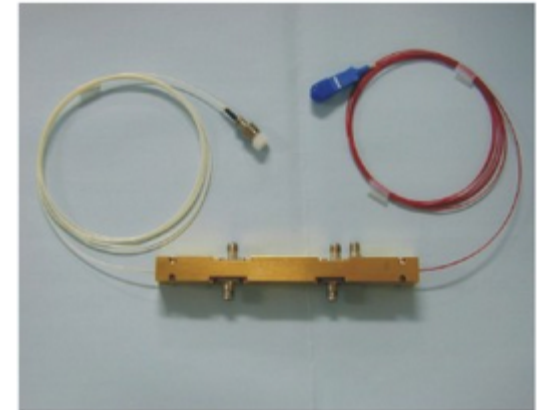
GaAs



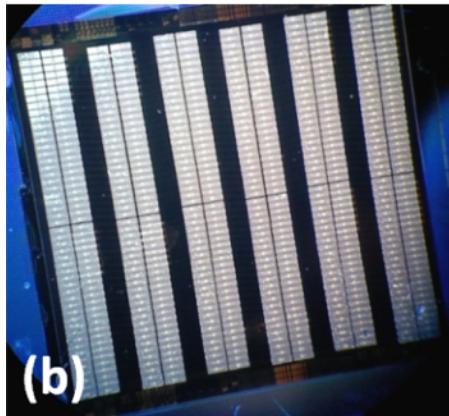
Silicon



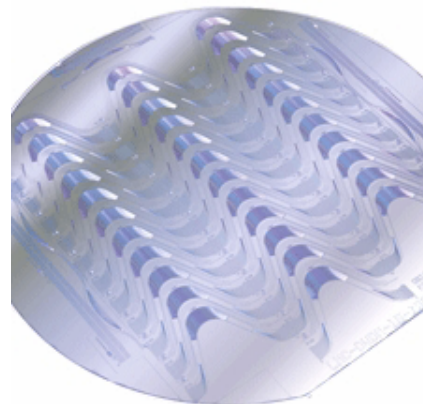
LiNbO<sub>3</sub>



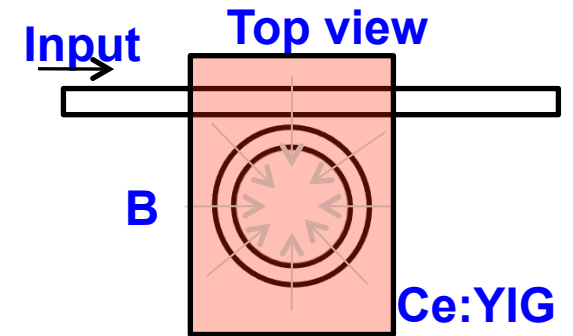
InP



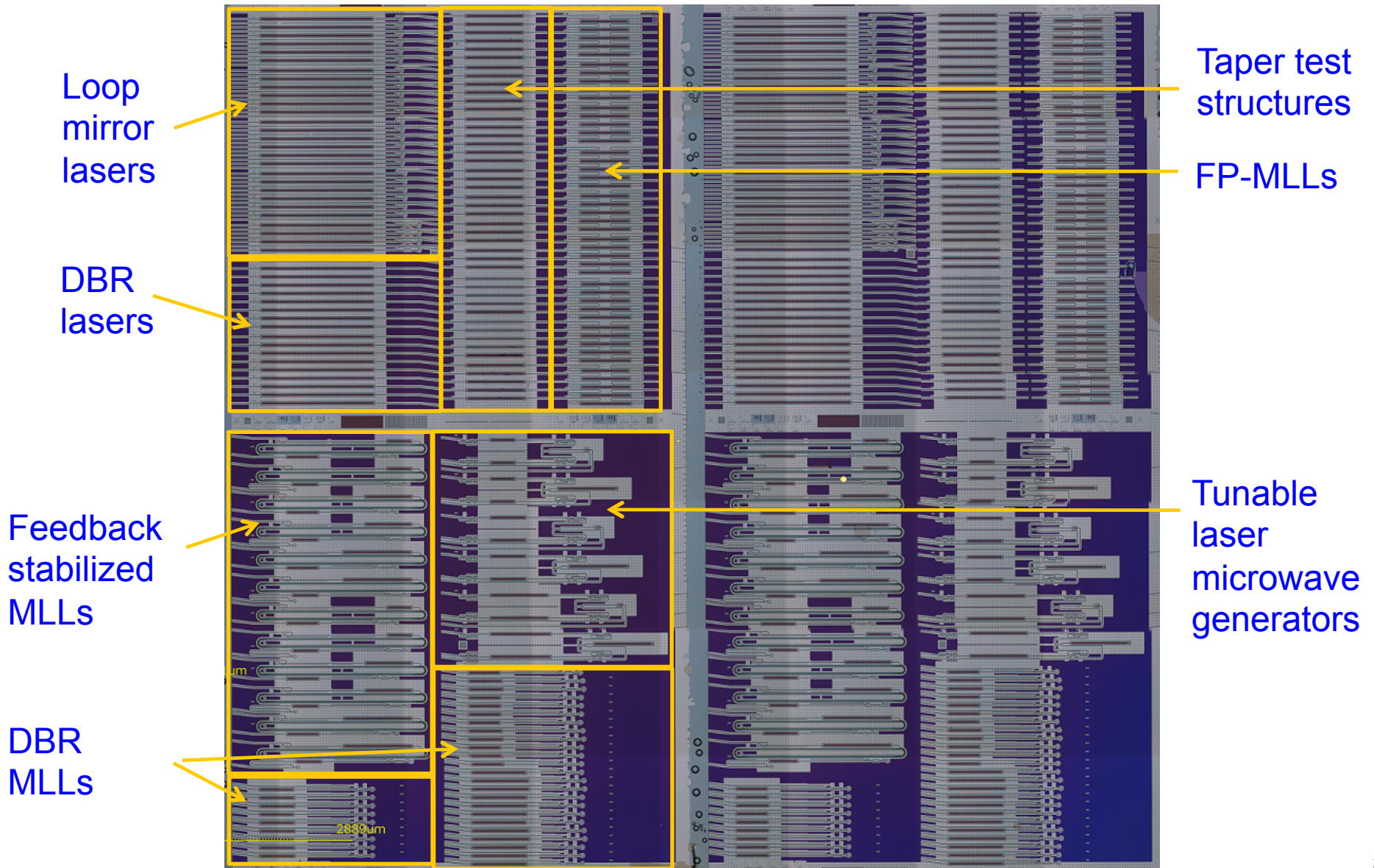
SiN/SiON/SiO<sub>2</sub>



Ce:YIG Isolator



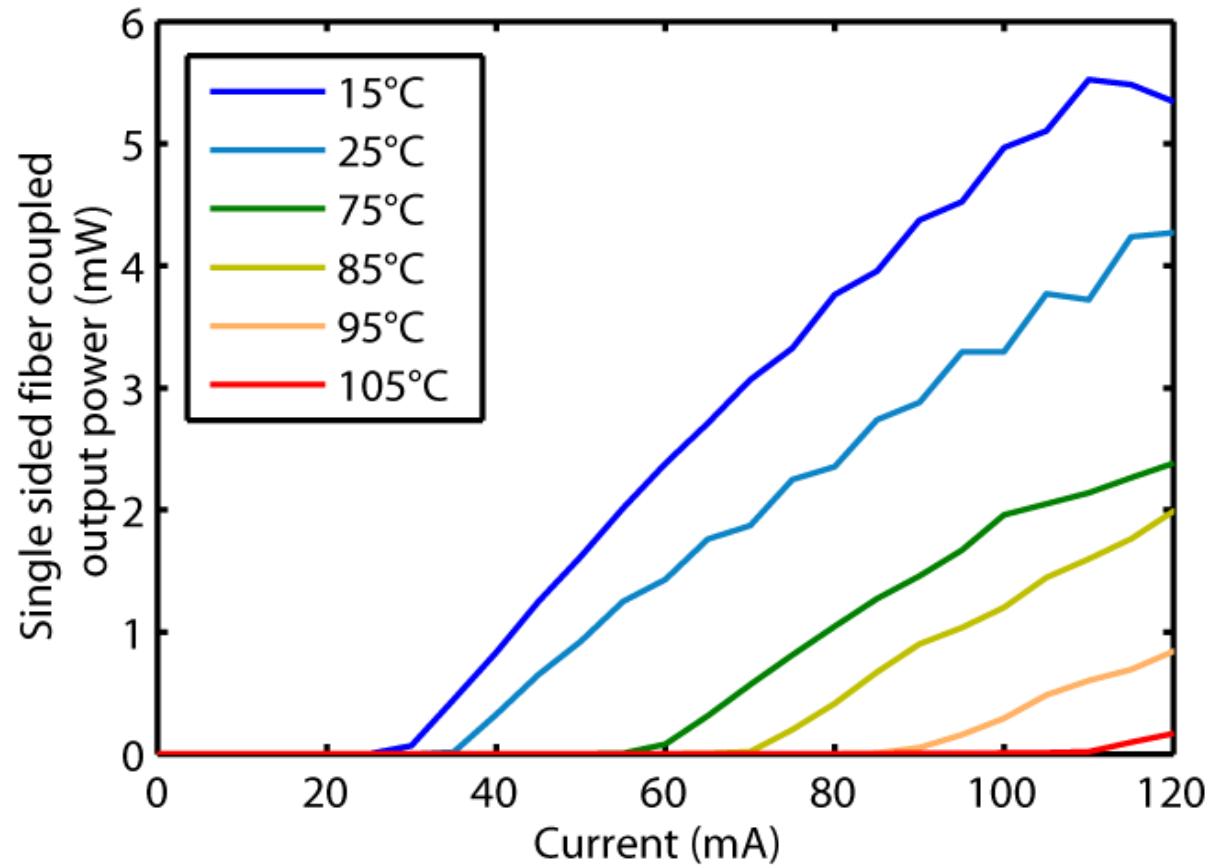
# UCSB Shuttle Run



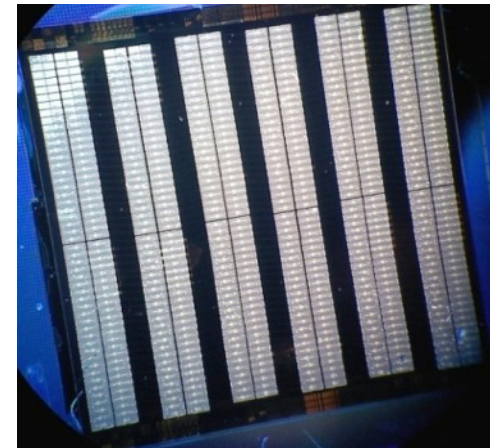
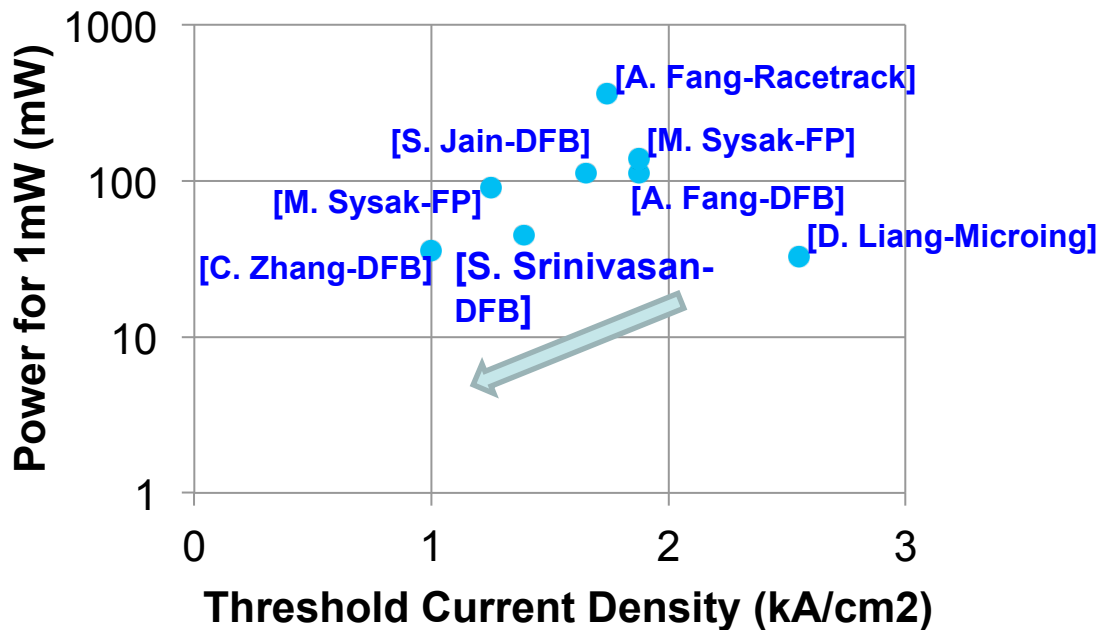
# Hybrid Silicon Quantum Well Lasers

## 105 C CW 1310 nm laser

- Max fiber coupled output power: 5.5 mW/facet
- $T_0$ : 80 °C
- Injection efficiency: 52 %

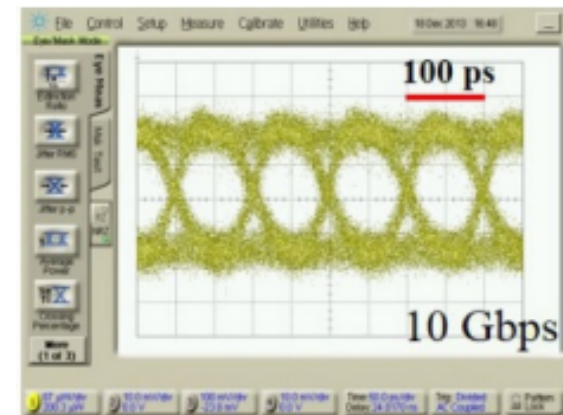
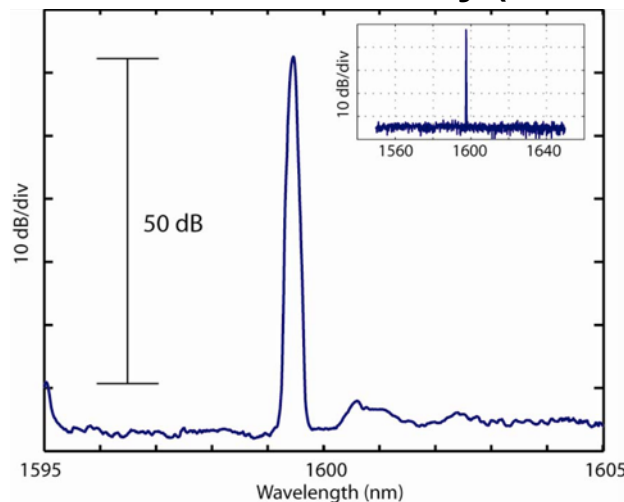


# UCSB DFB Quantum Well Hybrid Silicon Lasers



Chip showing 300 DFB lasers with yield >95%

Threshold Current Density (kA/cm²)

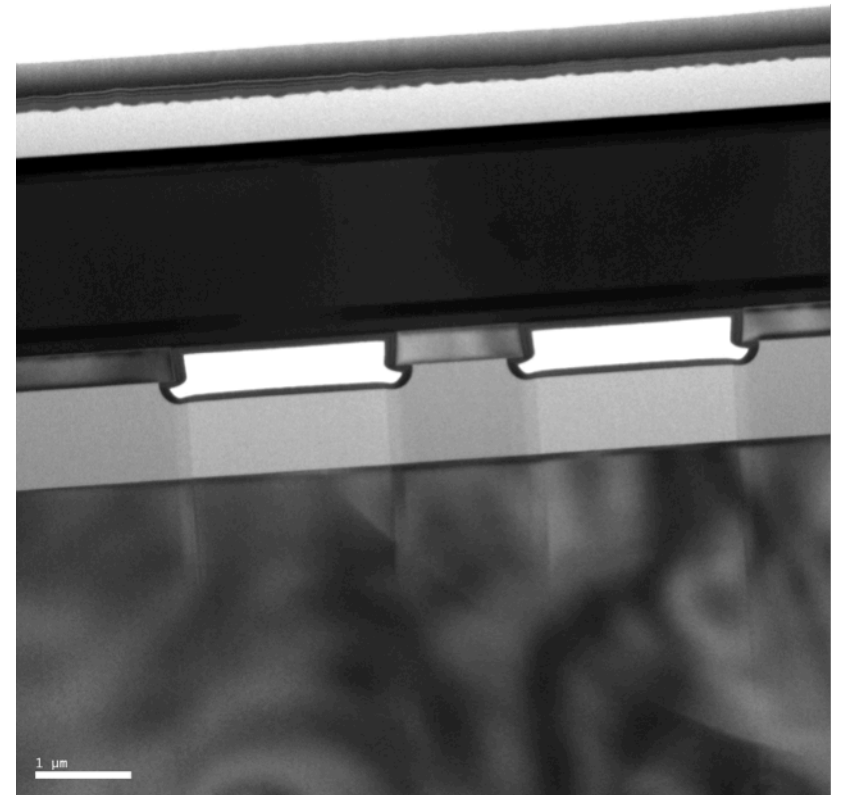
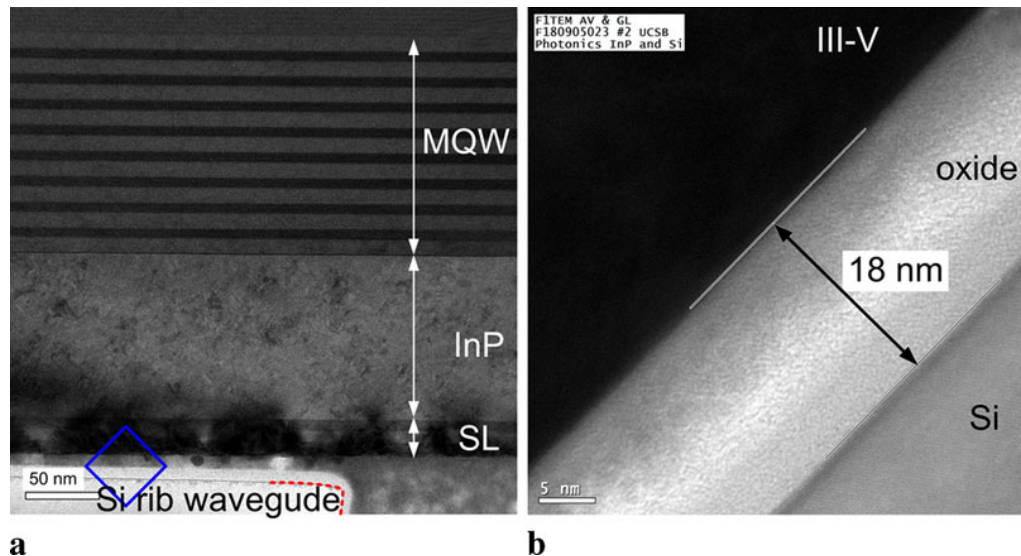


10Gbps direct modulation of a 200µm DFB laser

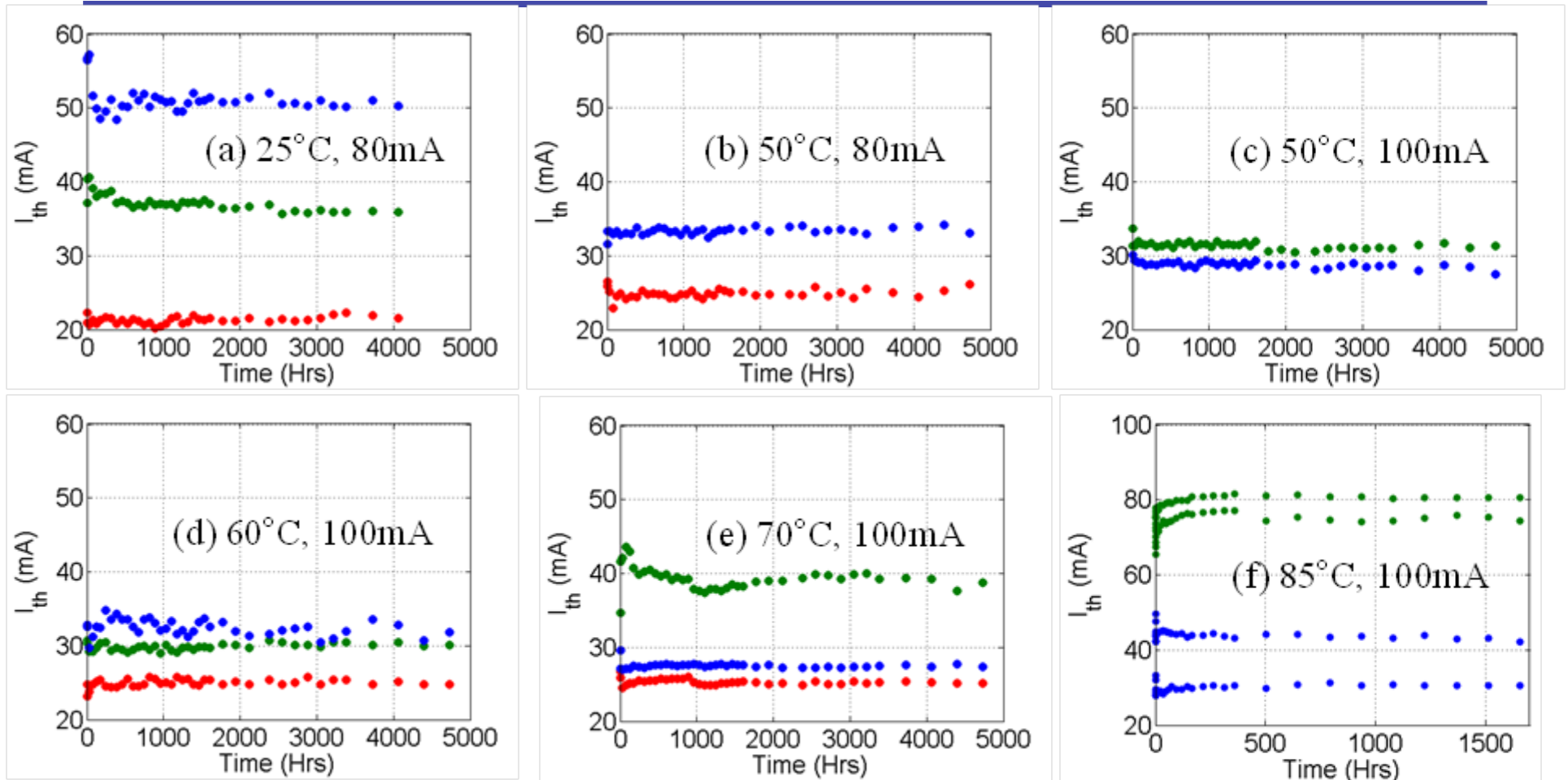


# Aging: Bonded III-V on Si

- Epitaxial growth on InP or GaAs followed by bonding to Si results in edge dislocations, which are not problem for laser lifetime.

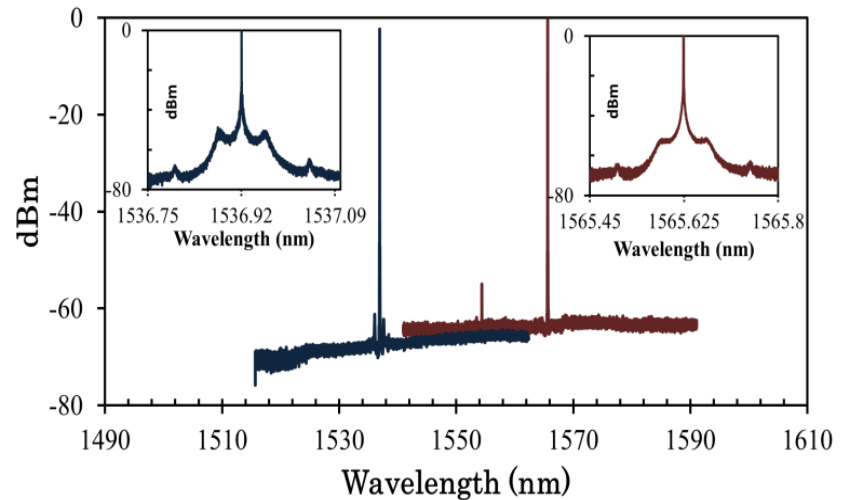
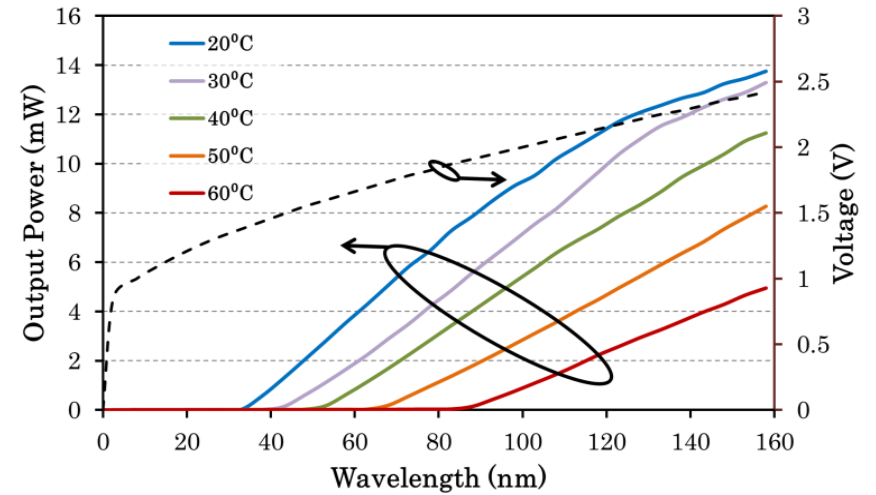
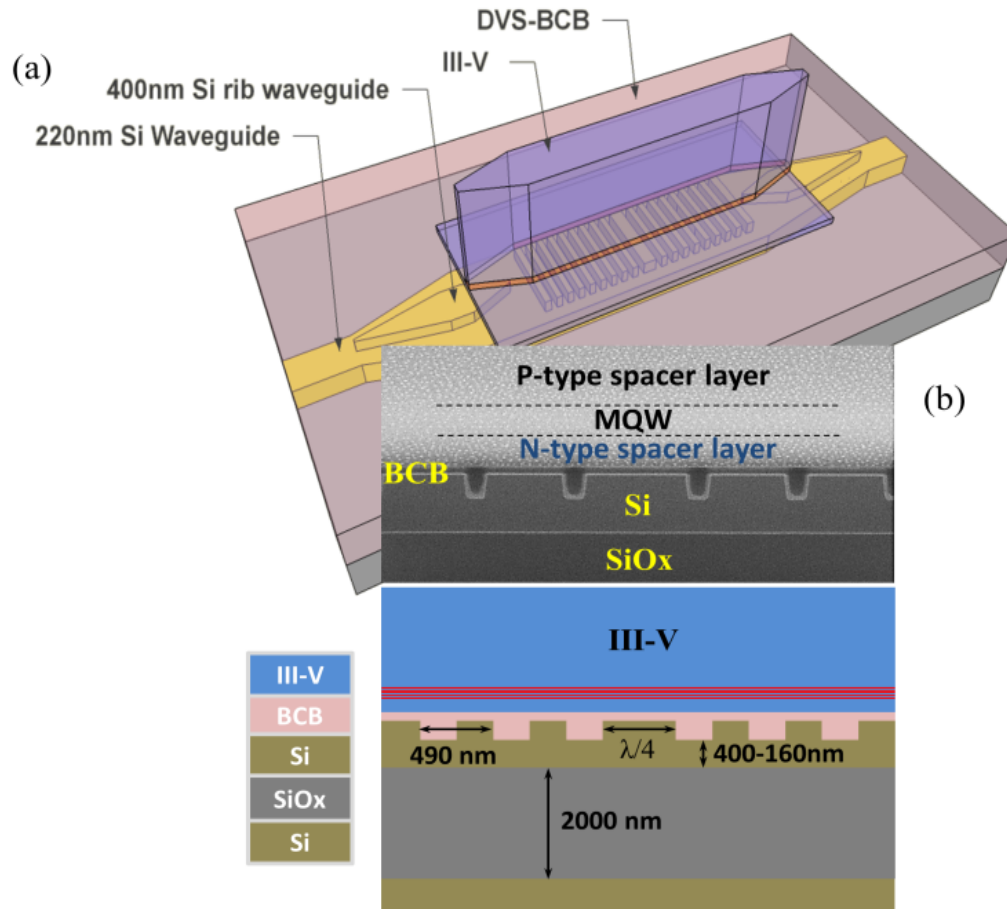


# Temperature Dependence of DFB Aging



Time to reach 50% degradation in threshold current at 70°C is >40,000hrs

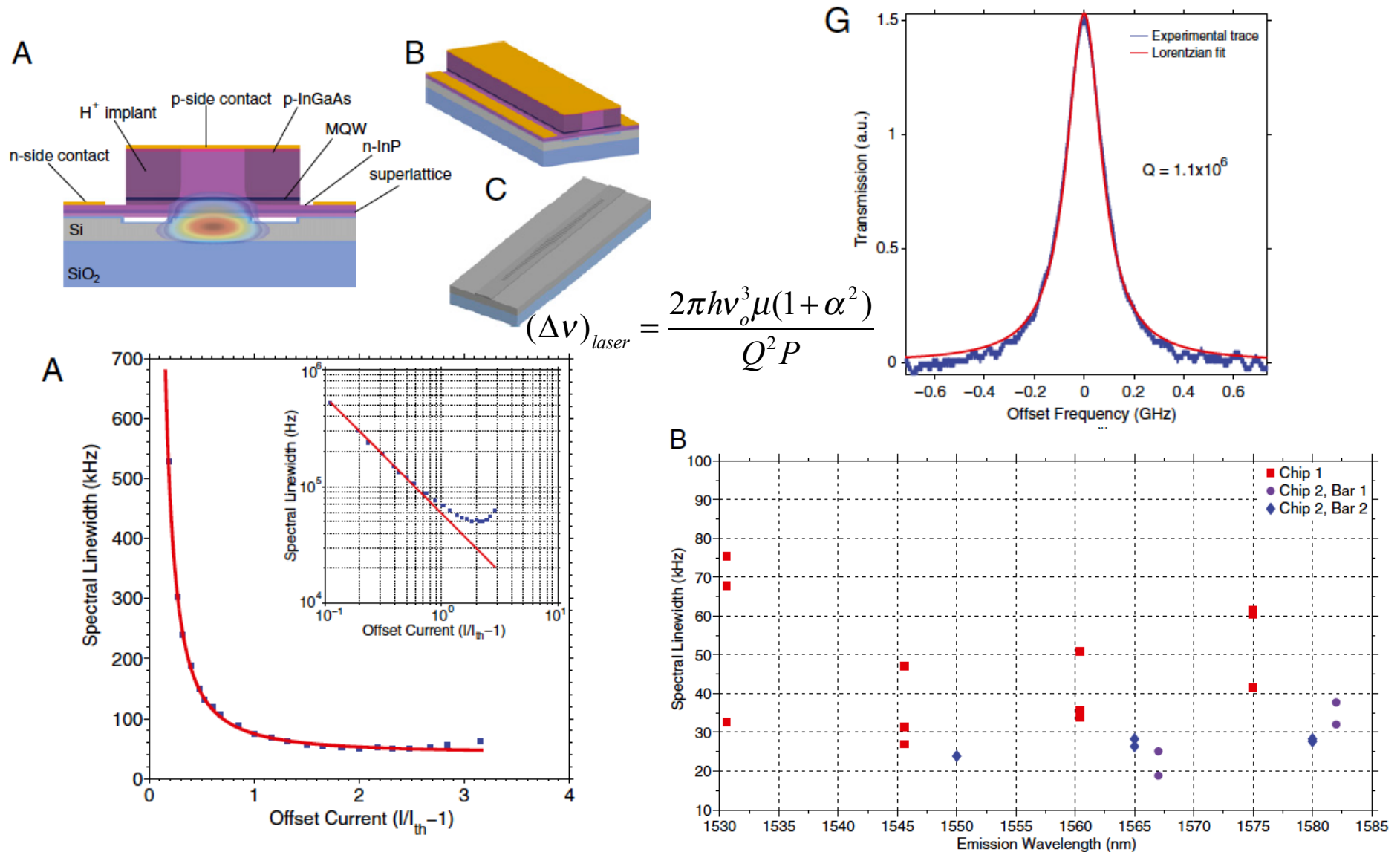
# DFB-type hybrid lasers



Keyvaninia, Opt Lett. 2013

# High-coherence semiconductor lasers based on integral high-Q resonators in hybrid Si/III-V platforms

Christos Theodoros Santis<sup>1</sup>, Scott T. Steger, Yaakov Vilenchik, Arseny Vasilyev, and Amnon Yariv<sup>1</sup>



**12:00** MB2 – “GaInAsP/InP Lateral-Current-Injection Membrane DFB Laser Integrated with GaInAsP Waveguides on Si Substrate”

Daisuke Inoue, Jieun Lee, Takuo Hiratani, Yuki Atsuji, Tomohiro Amemiya, Nobuhiko Nishiyama, Shigehisa Arai, *Tokyo Institute of Technology, Japan*

A lateral-current-injection membrane DFB laser integrated with GaInAsP waveguides and a detector was fabricated by butt-joint regrowth technique. As a result, a threshold current of 700  $\mu\text{A}$  under room-temperature CW condition was obtained.

## BCB Bonding

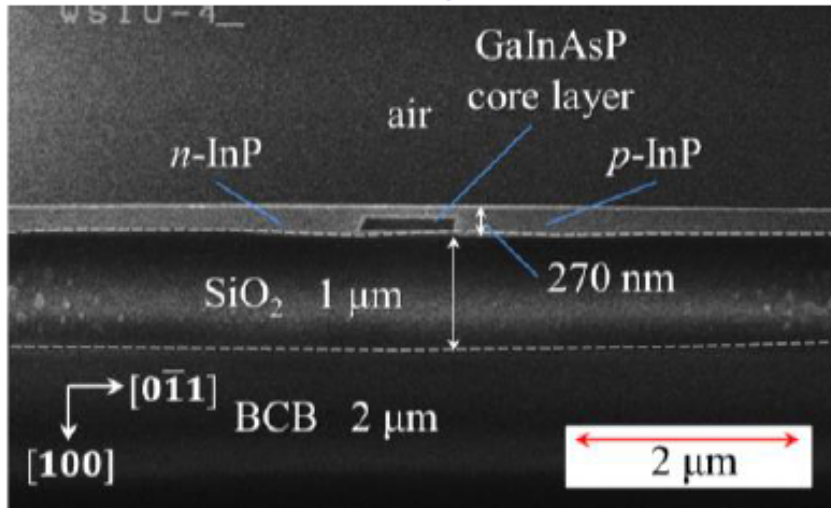
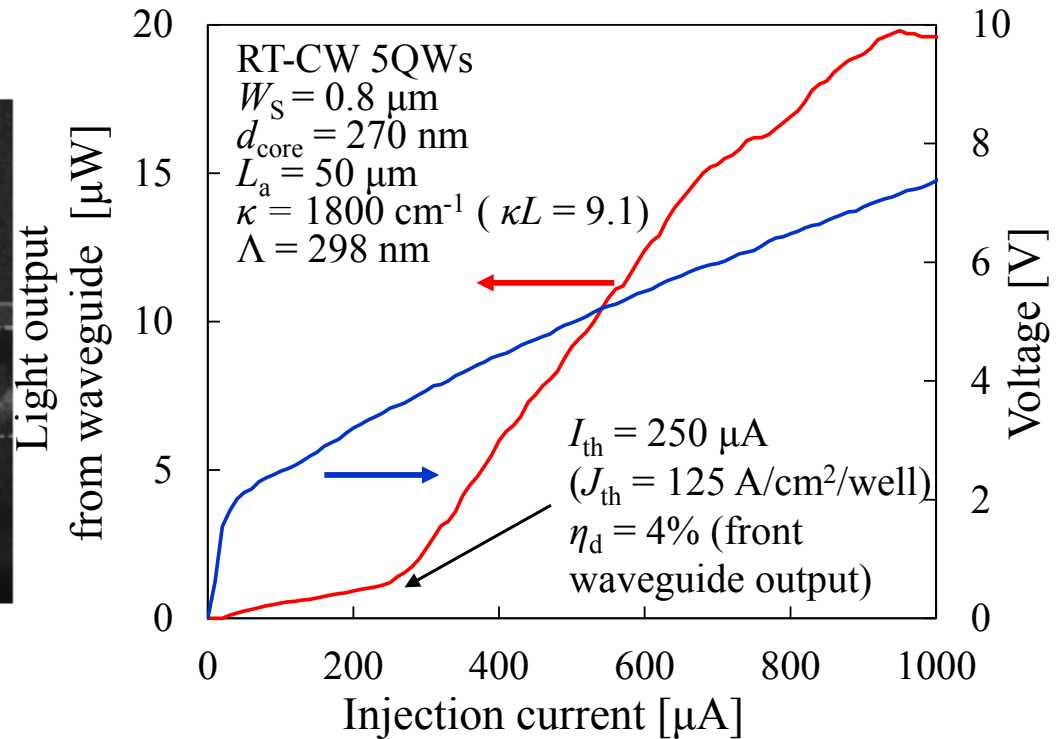


Fig. 2 A SEM image of cross sectional of GaInAsP





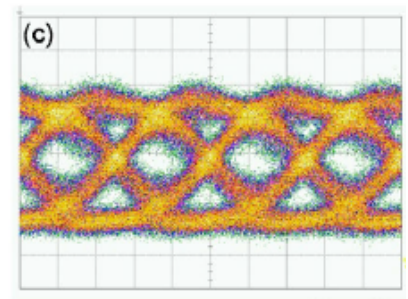
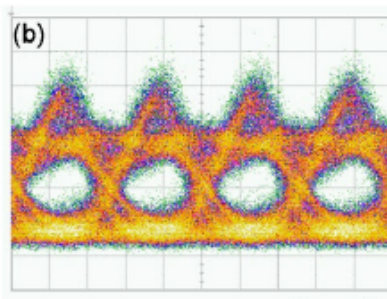
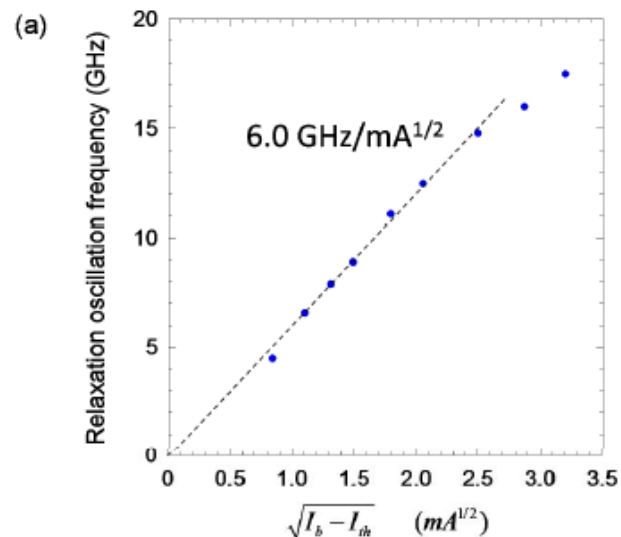
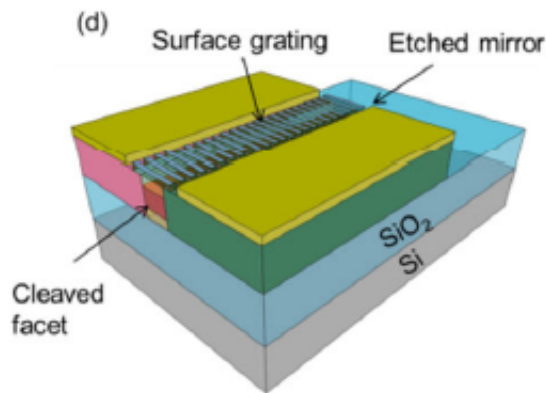
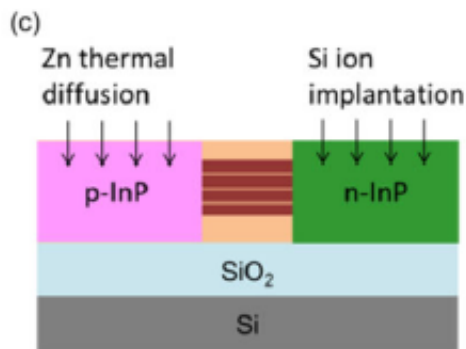
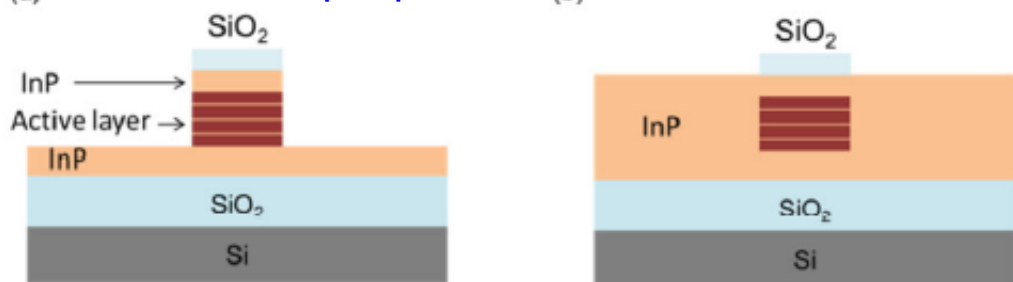
# 40-Gbit/s Direct Modulation of Membrane Buried Heterostructure DFB Laser on SiO<sub>2</sub>/Si Substrate

Shinji Matsuo, Takuro Fujii, Koichi Hasebe, Koji Takeda, Tomonari Sato, and Takaaki Kakitsuka

NTT Photonics Laboratories, NTT Corporation

Bonded with oxygen plasma assisted bonding.  
Then regrown with MOCVD.

(a) 1.5 mW cw output power

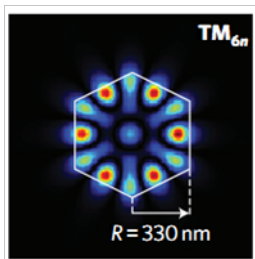


40 Gbit/s

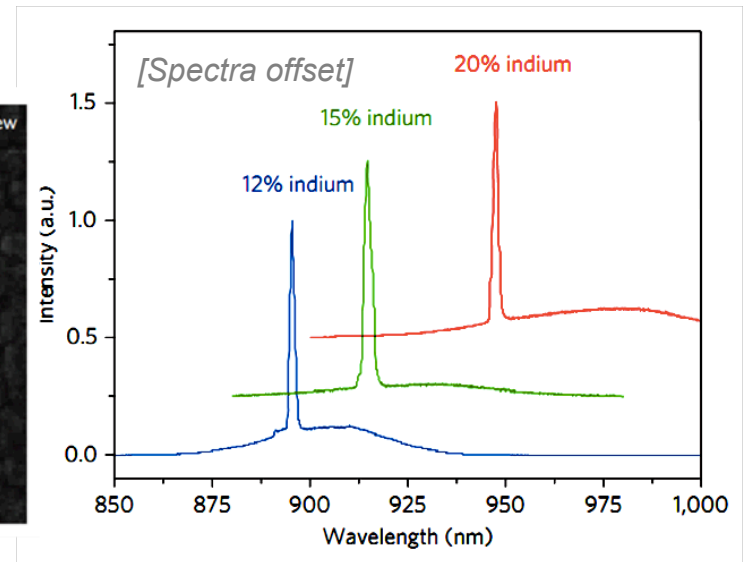
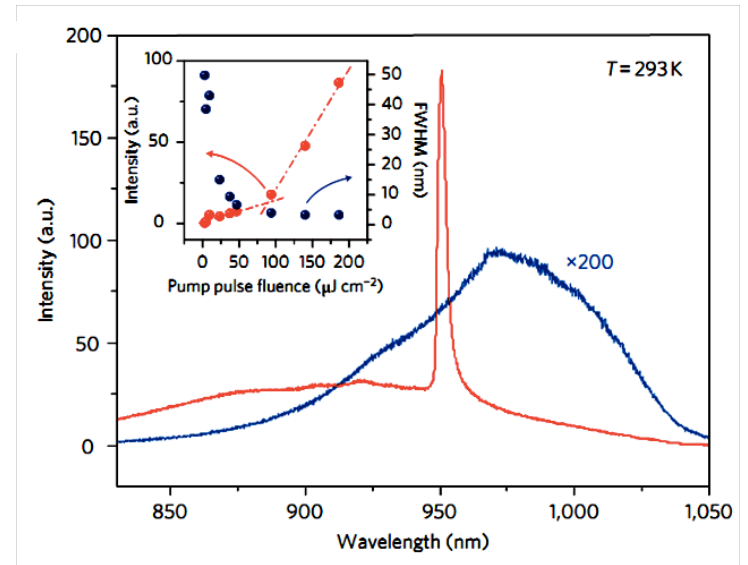
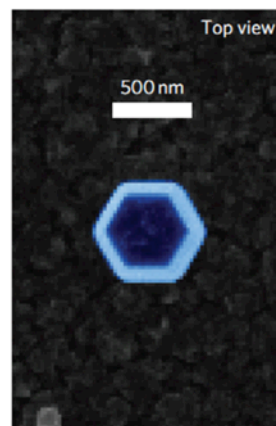
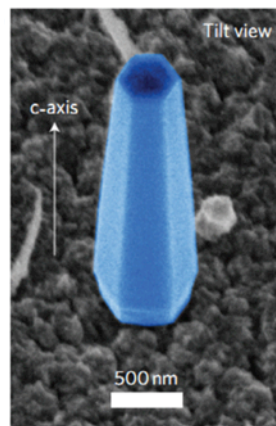
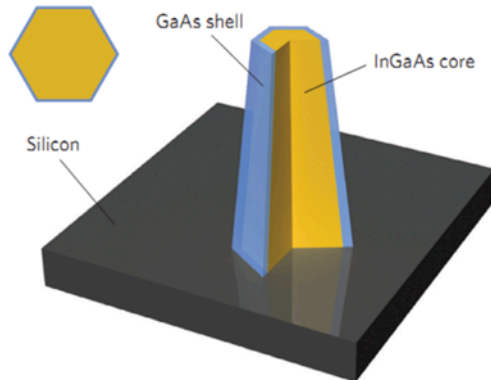
# Nanolasers grown on silicon

C. Chang Hasnain (UC Berkeley)

- III–V nanolaser grown on silicon;
- room-temperature operation;
- subwavelength volume;
- helically propagating cavity modes.



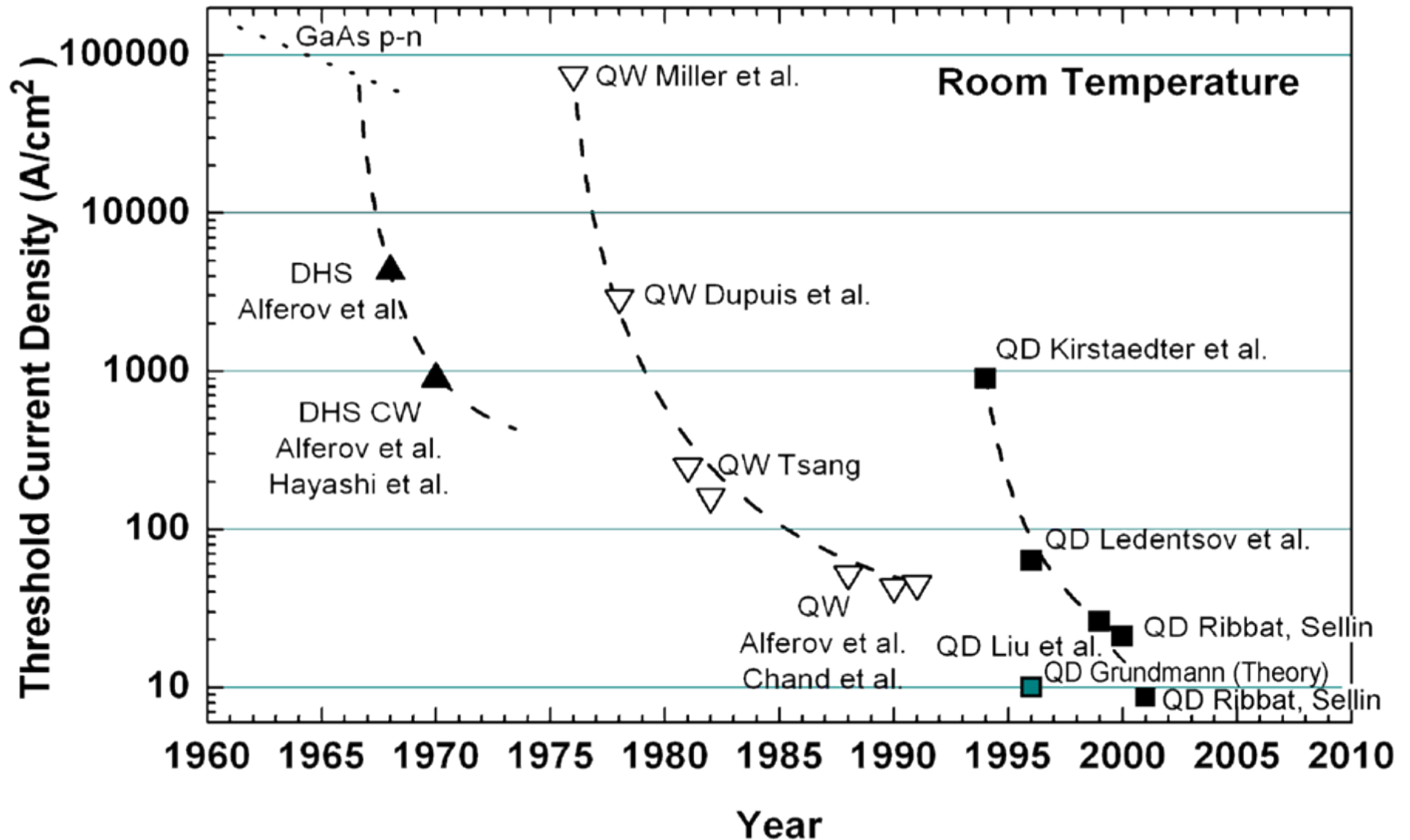
*R. Chen et al.,  
Nat. Photon. 2011*



# Quantum Dot Lasers



# Threshold Current Densities of Semiconductor Lasers



QD-based photonic devices are less power hungry

# Early work on quantum dot lasers

## Theoretical work

- The first proposal : Arakawa (1982)
- Reduced temperature dependence: Arakawa (1982)
- Higher speed modulation : Arakawa, Yariv (1984)
- Zero-a-parameter, low-chirping : Arakawa, Yariv (1984)
- Lower threshold current density : Asada/Suematsu (1986)
- p-doping: Arakawa (1982, 1991)
- Tunneling injection: Arakawa (1992)

$$f_r = \frac{1}{2\pi} \sqrt{\frac{\left(\frac{\partial g}{\partial n}\right)}{\tau_p}} S$$

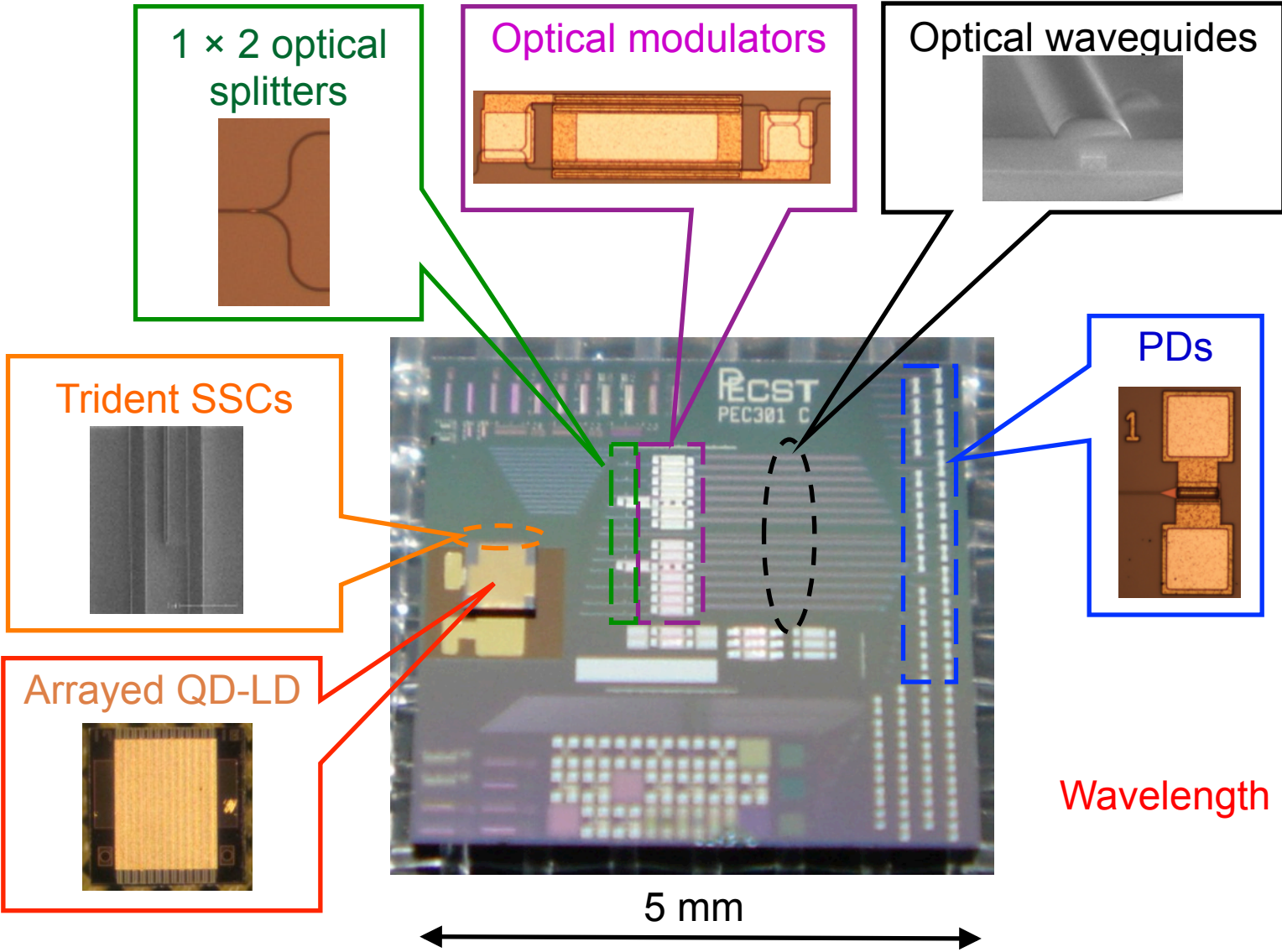
$$\Delta\nu = (1 + \alpha^2) \Delta\nu_{St} \quad \left( \alpha = \frac{\partial\chi_R/\partial n}{\partial\chi_I/\partial n} \right) \rightarrow 0$$

## High magnetic field experiment up to 30Tesla

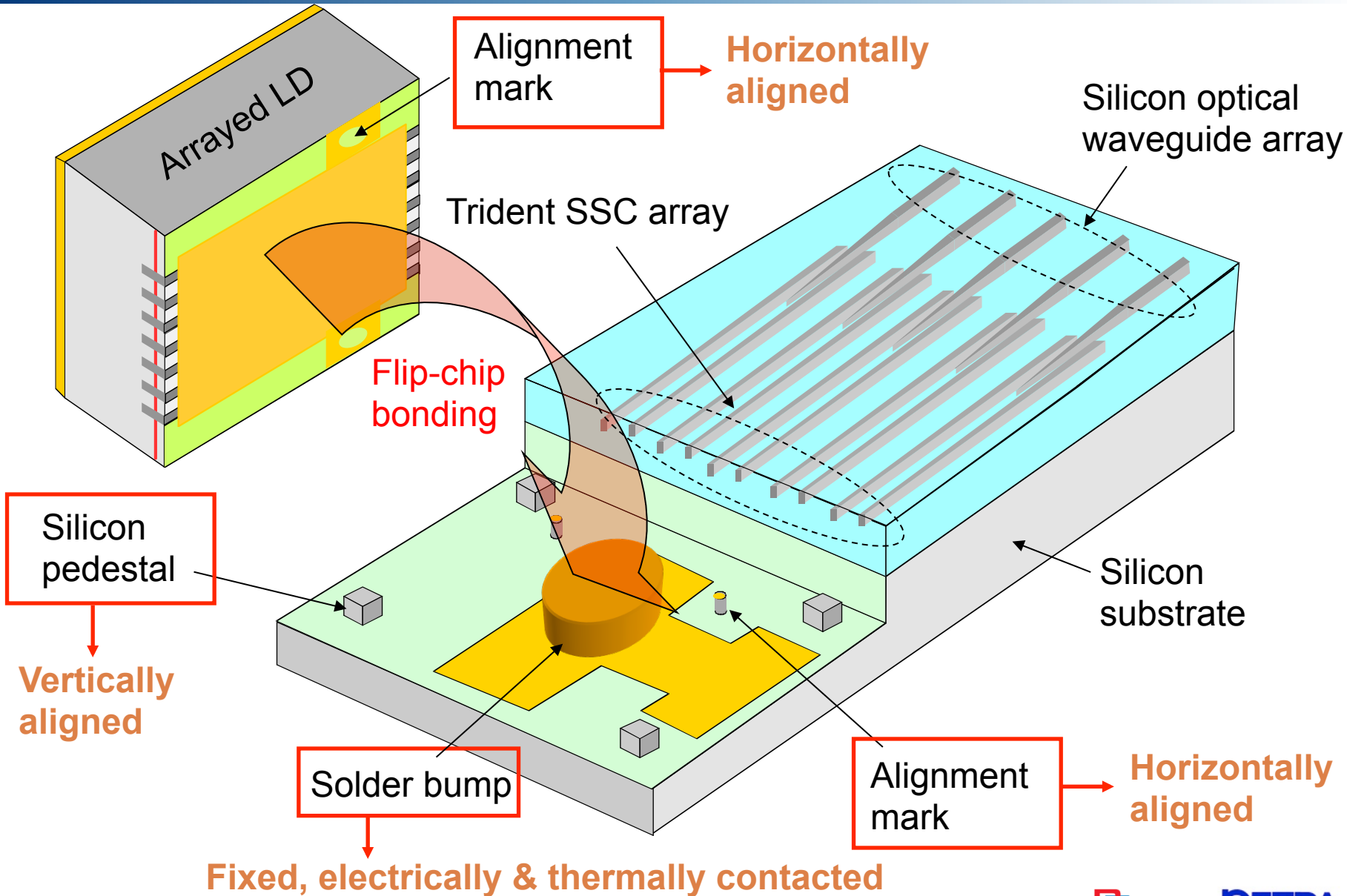
Enhanced modulation speed  
Reduced a-parameter

Arakawa, Vahala, Yariv (1984-86)  
Arakawa, Vahala, Yariv (1984-86)

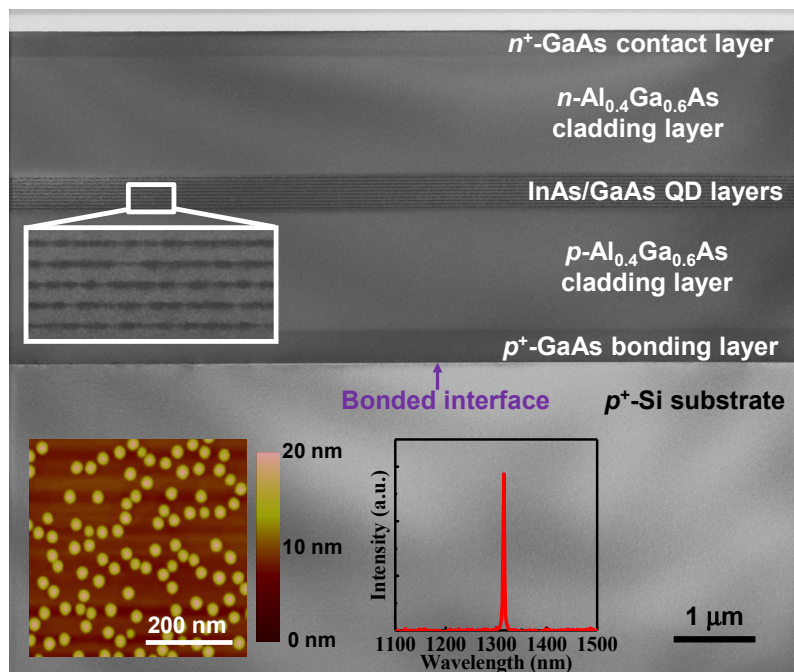
# QD lasers on silicon optical interposers



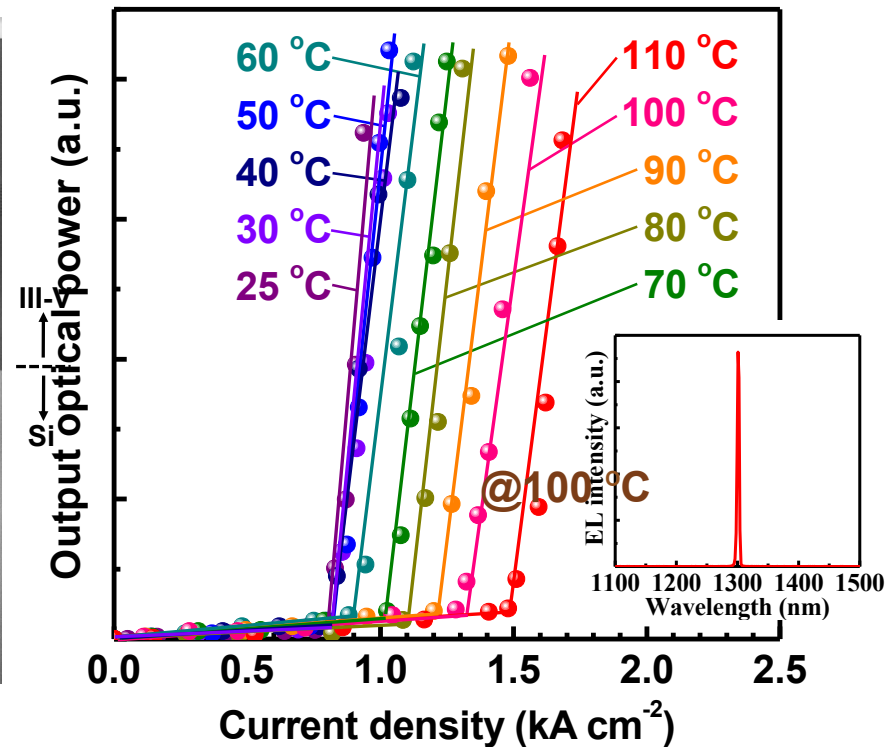
# Hybrid QD laser array on silicon by flip-chip bonding



# Hybrid QD laser on silicon by wafer bonding technique



K. Tanabe et al, *Sci. Rep.* 2, 349 (2012)



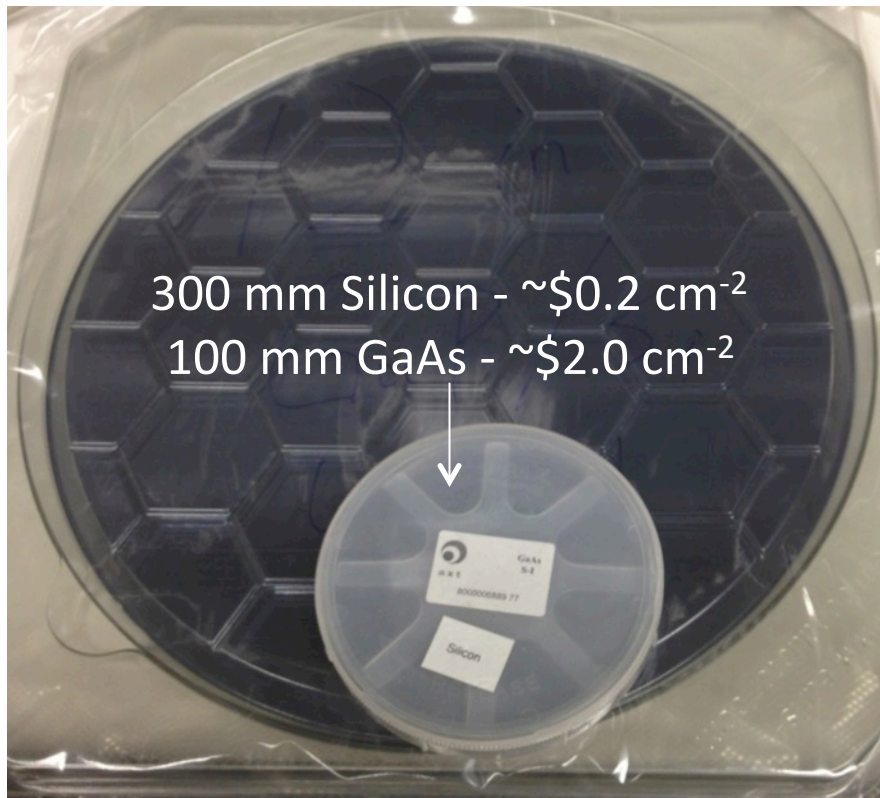
- Lasing at telecom O-band 1.3 mm (GS transition of InAs QDs)
- Realized lasing operation at over 100 °C

K. Tanabe et al, *Appl. Phys. Express* 6, 082703 (2013)

Table 1. Approximate growth substrate minimum cost and maximum size

	<i>InAs</i>	<i>InP</i>	<i>GaAs</i>	<i>SOI</i>	<i>Si</i>
Substrate Cost (\$/cm <sup>2</sup> )	18.25	4.55	1.65	1.30	0.20
Maximum size (mm)	76	150	200	450	450

[1]



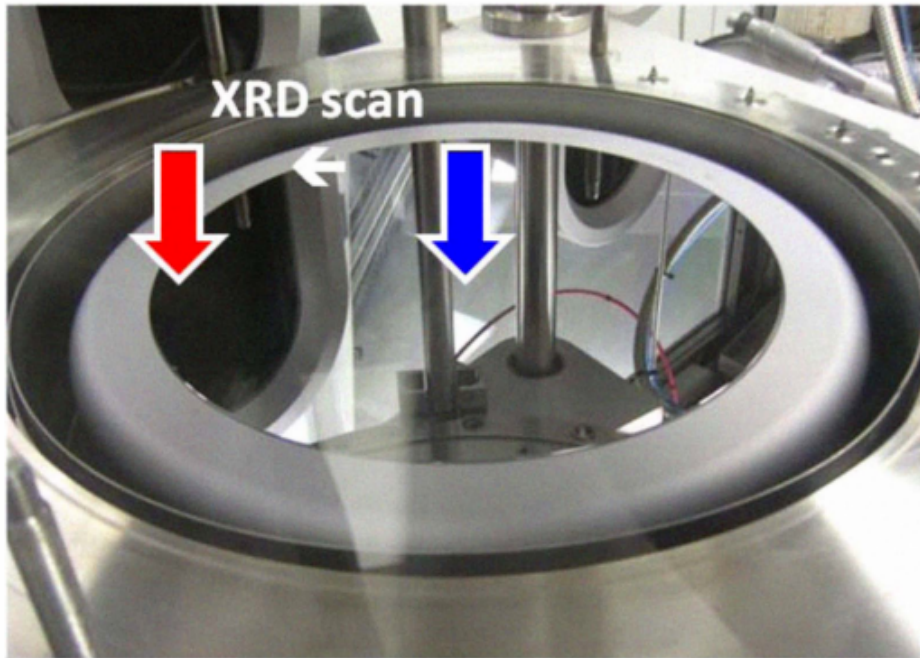
- CMOS processing of photonics is already happening, yet high cost and small size of III-V wafers remains an issue.
- **Goal:** Grow III-V lasers on larger and cheaper silicon substrates without sacrificing laser performance for lower cost and higher throughput.

[1] Bowers, John E., et al. "A Path to 300 mm Hybrid Silicon Photonic Integrated Circuits." OFC 2014

(Courtesy of Dr. Jordan Lang, Yale)

# UCSB III-V growth on 300 mm Silicon Wafers

GaP on 300 mm Silicon by NAsP III/V GmbH  
using MOVPE (AIXTRON CRIUS CCS reactor)



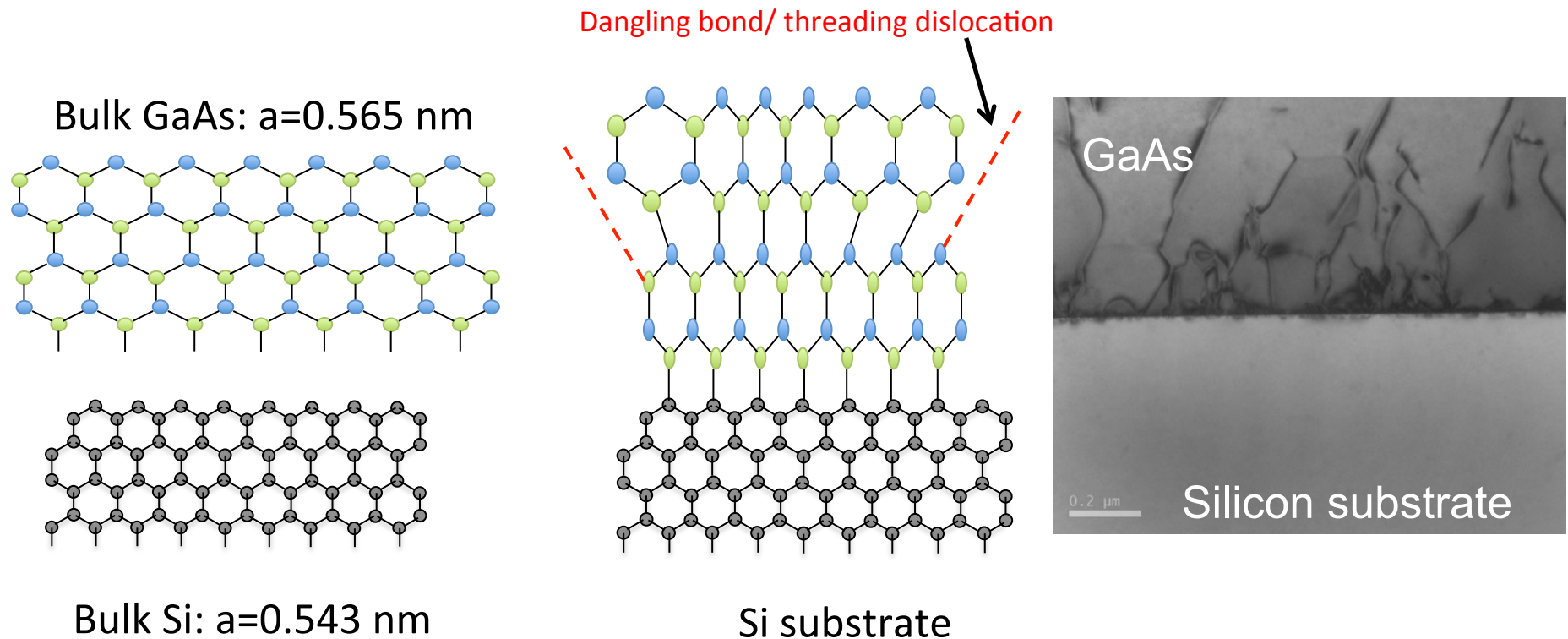
World's 1<sup>st</sup> 12" GaAs on Si epiwafer by IQE,  
using MBE (Veeco Gen-2000 reactor).



B. Kunert *et al.* 69<sup>th</sup> Device Research Conference,  
Santa Barbara (2011)

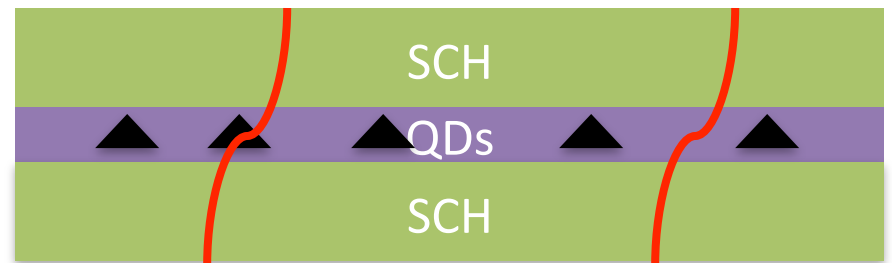
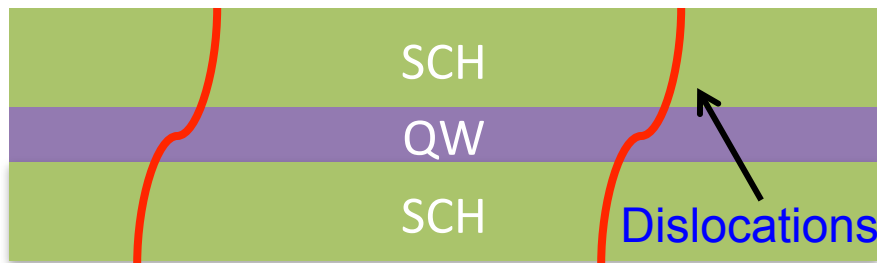
(Courtesy of Amy Liu, IQE Inc.)

- Polarity, lattice & thermal expansion mismatch between silicon and III-Vs result in high dislocation densities
  - High thresholds (or no lasing), and poor reliability for QW lasers.

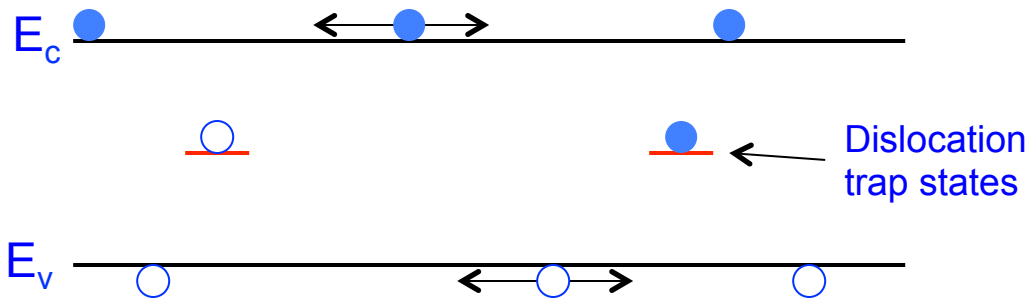




# Solution: Use Quantum Dots!



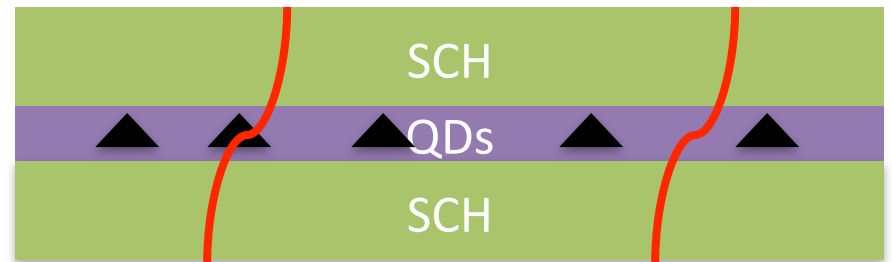
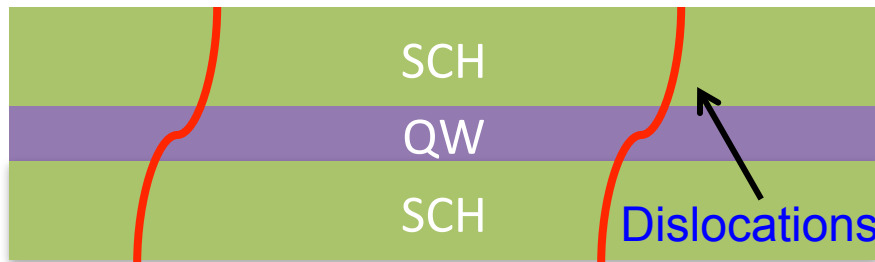
In-plane band diagram:



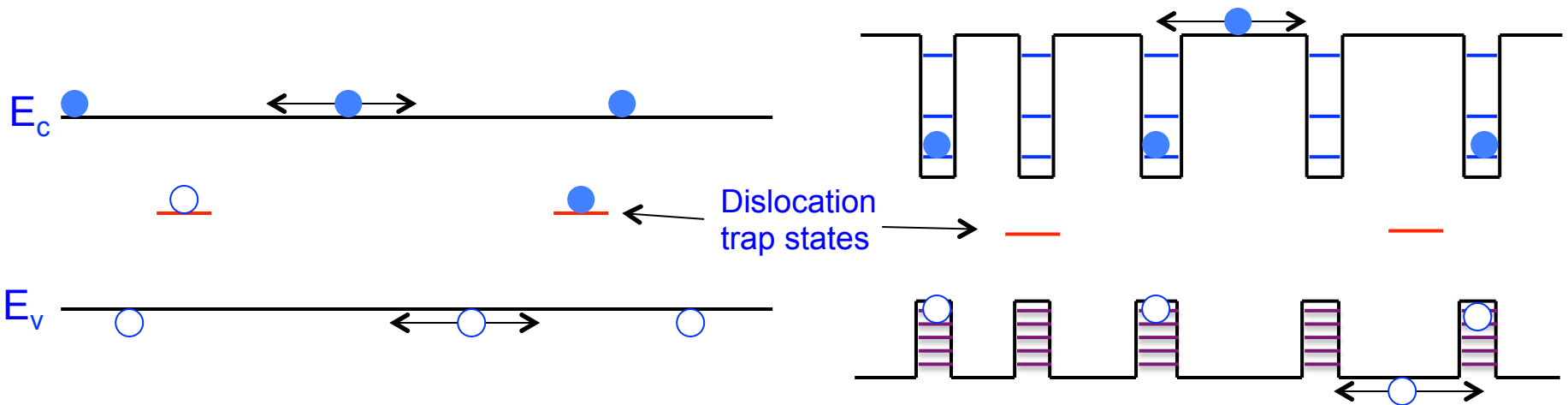
# Solution: Use Quantum Dots!

1991 – “Semiconductor Structure for Optoelectronic Components with Inclusions” (Jean Gerard & Claude Weisbuch), U.S. Patent No. 5,075,742

- 3D confinement provided by quantum dots prevents carriers from migrating to dislocations.

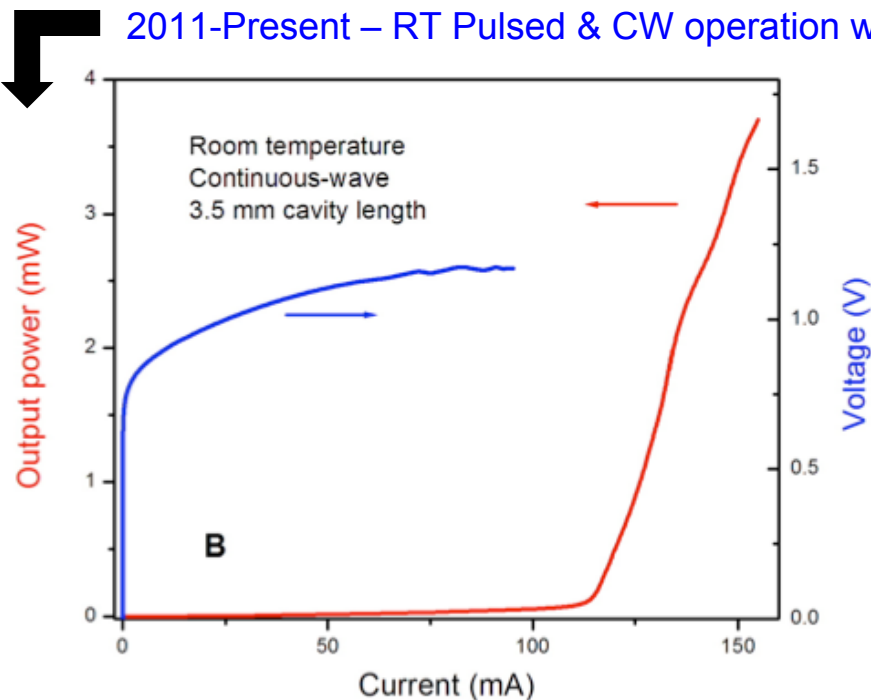


In-plane band diagram:

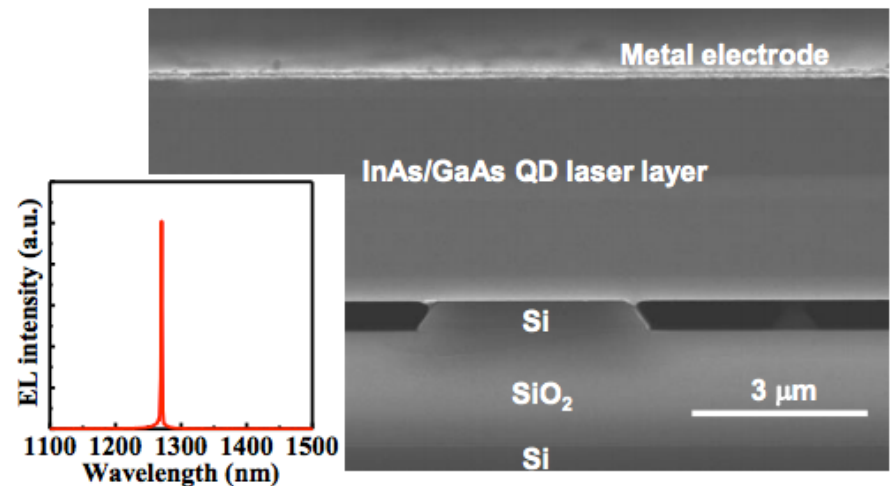


# UCSB History of Quantum Dot Lasers on Silicon

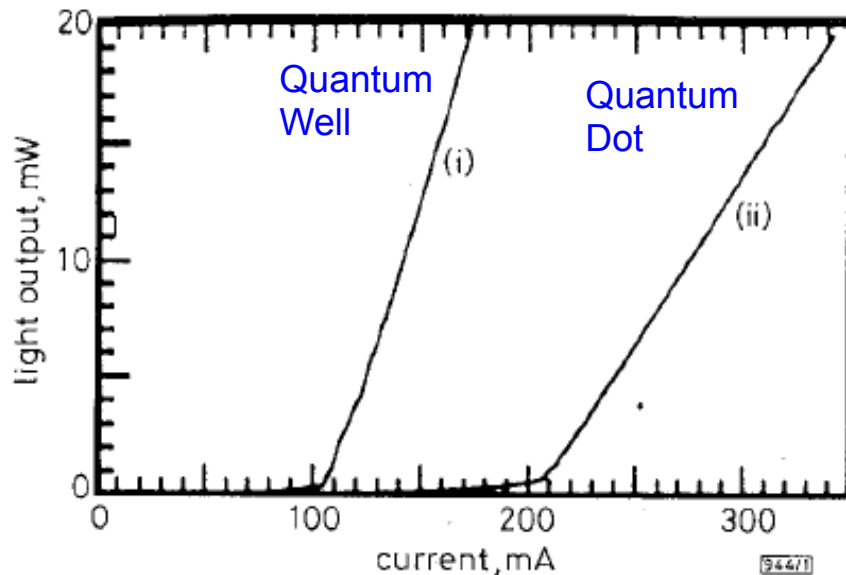
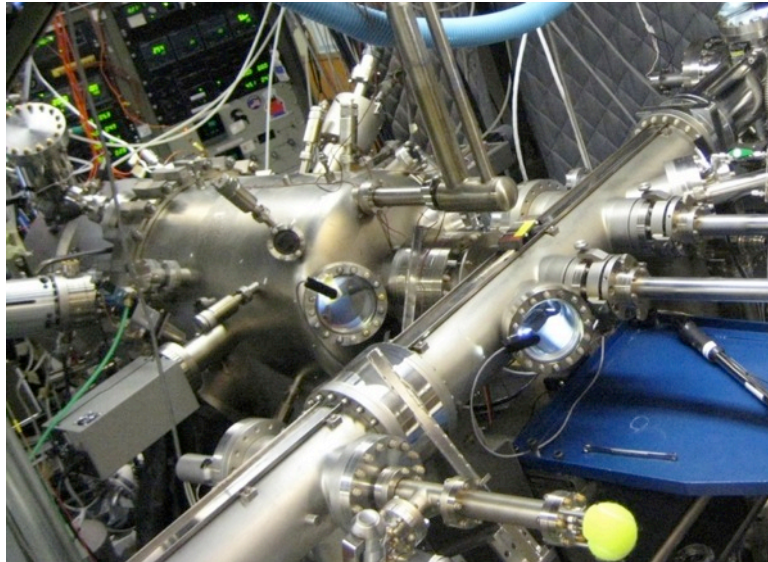
- 1991 – “Semiconductor Structure for Optoelectronic Components with Inclusions” (Jean Gerard & Claude Weisbuch), U.S. Patent No. 5,075,742
- 1999 – First laser operation with  $\text{In}_{.4}\text{Ga}_{.6}\text{As}$  QDs on Si @ 1  $\mu\text{m}$ . Pulsed at 80 K (Michigan)
- 2000 – RT CW operation of quantum-dot like laser on Si @ 0.854  $\mu\text{m}$  (Nagoya IT)
- 2005 – RT Pulsed operation with  $\text{In}_{.5}\text{Ga}_{.5}\text{As}$  QDs on Si @ 1  $\mu\text{m}$  (Michigan)
- 2011-Present – RT Pulsed & CW operation with wafer bonded InAs QDs on Si (U. of Tokyo)
- 2011-Present – RT Pulsed & CW operation with InAs QDs on Si & Ge/Si @ 1.3  $\mu\text{m}$  (UCL)



Lee, Andrew, et al. "Continuous-wave InAs/GaAs quantum-dot laser diodes monolithically grown on Si substrate with low threshold current densities." *Optics express* 20.20 (2012): 22181-22187.

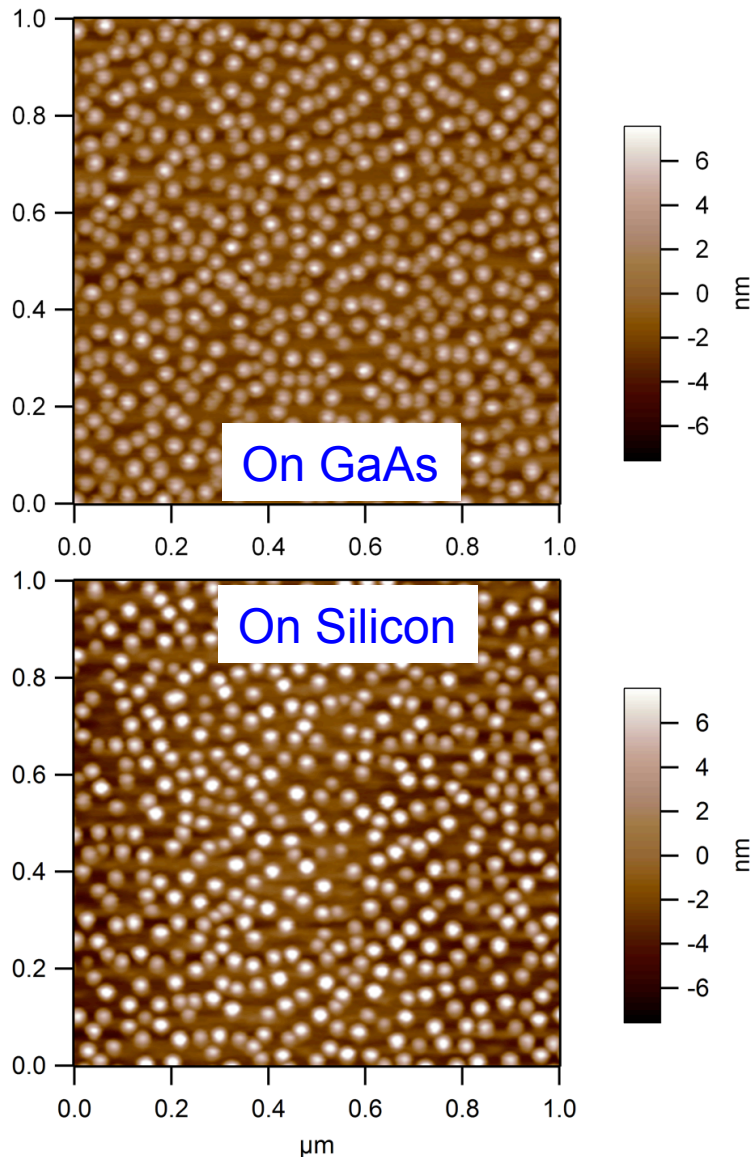


Tanabe, Katsuaki, and Yasuhiko Arakawa. "1.3  $\mu\text{m}$  InAs/GaAs Quantum Dot Lasers on SOI Waveguide Structures." *CLEO: Science and Innovations*. Optical Society of America, 2014. 51

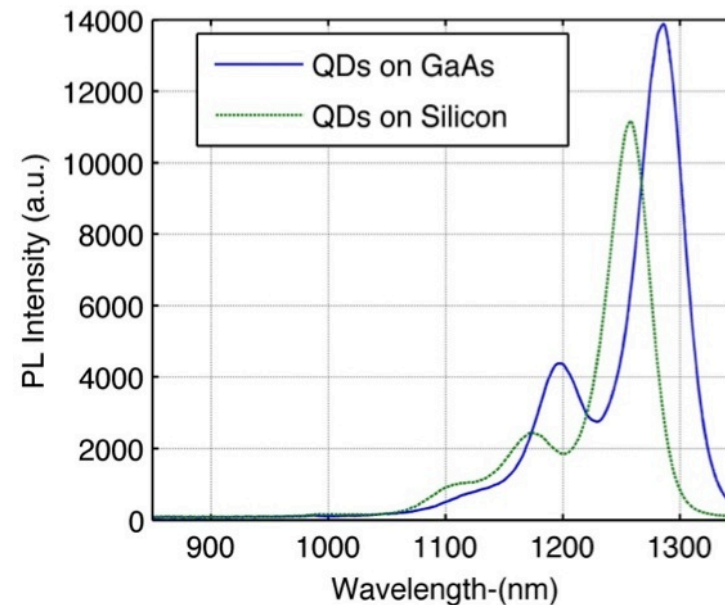


- 1993 – First ever self assembled InGaAs quantum dots reported by D. Leonard, S. Denbaars, P. Petroff et al. (*Appl. Phys. Lett.* **63**)
- 1995 – First 1.3  $\mu\text{m}$  photoluminescence from InGaAs by R. Mirin, A. C. Gossard, J. E. Bowers et al. (*Appl. Phys. Lett.* **67**)
- 1996 - R. P. Mirin, A. Gossard, and J. E. Bowers, “Room Temperature Lasing From InGaAs Quantum Dots,” *Electronics Letters*, 32 (18), 1732,
- 2014 – High Performance continuous wave 1.3  $\mu\text{m}$  quantum dot lasers on silicon by A. Y. Liu, A. C. Gossard, J. E. Bowers et al. (*Appl. Phys. Lett* **104**)

# UCSB MBE growth of InAs Quantum Dots



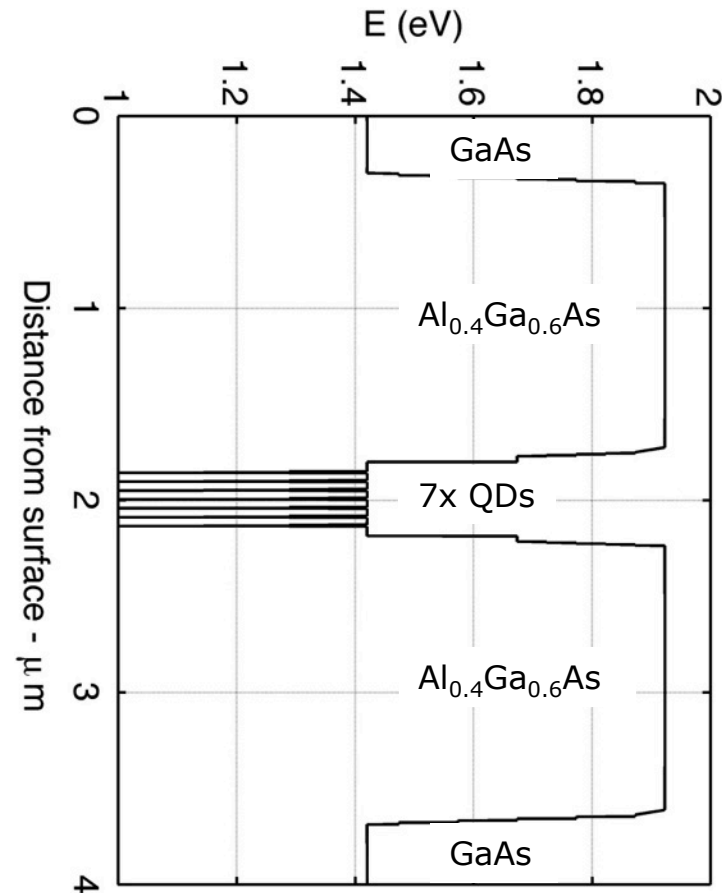
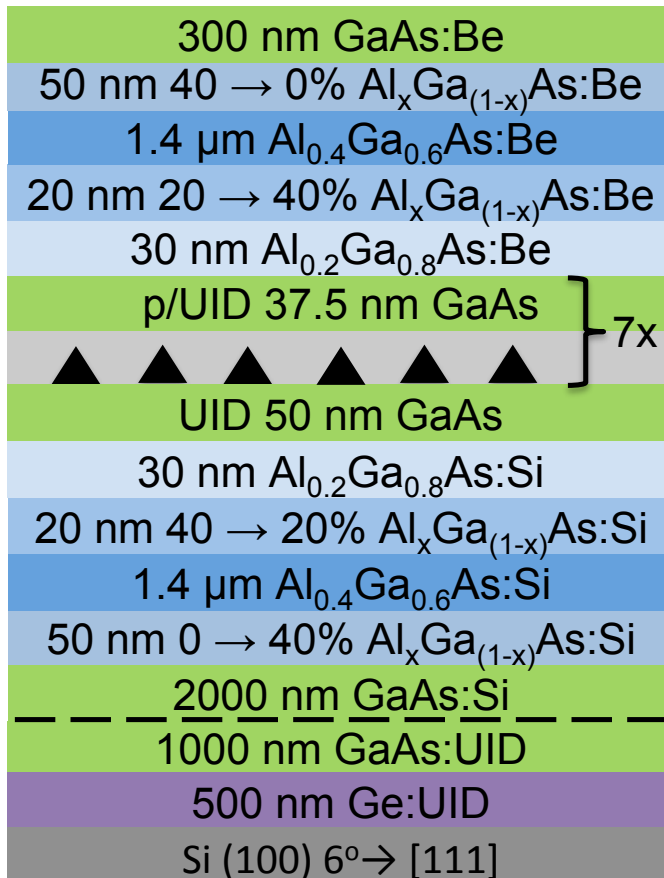
- InAs/GaAs self assembled quantum dots by Stranski-Krastanov layer/island growth mode
- Average quantum dot density:  $\sim 5 \times 10^{10} \text{ cm}^{-2}$
- PL peak around 1285nm on GaAs and 1255nm on Si
  - 47nm/35 meV PL linewidth



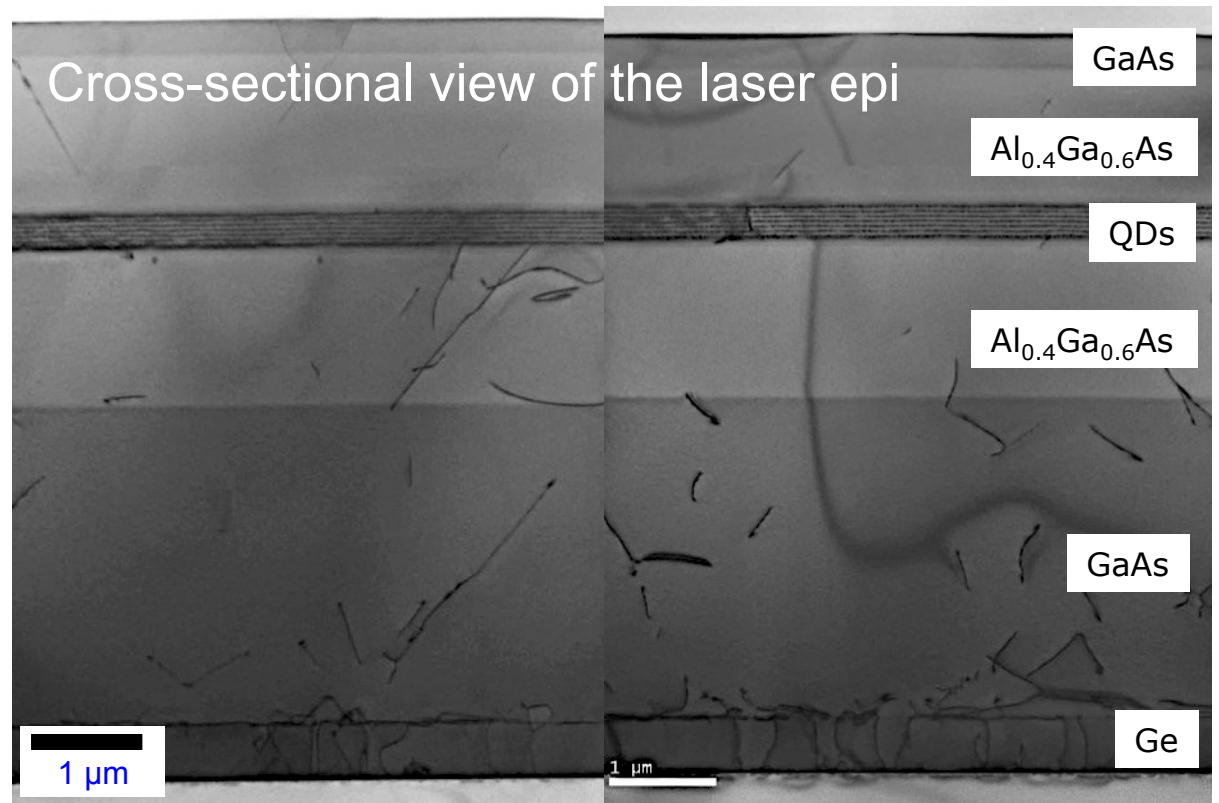
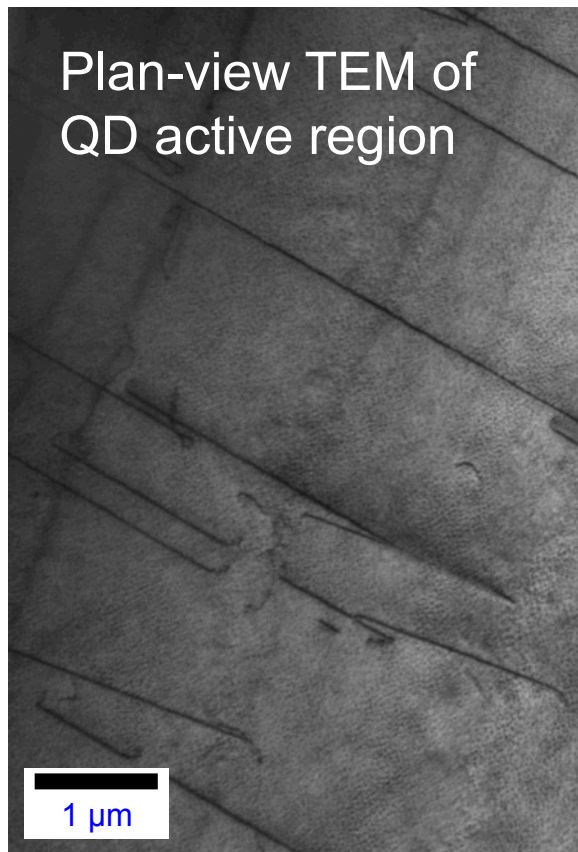
- A. Y. Liu *et al*, "MBE growth of P-doped 1.3 μm InAs quantum dot lasers on silicon". *J. Vac. Sci. Technol. B*. 2014

# GRINSCH QDLs on Ge/Si

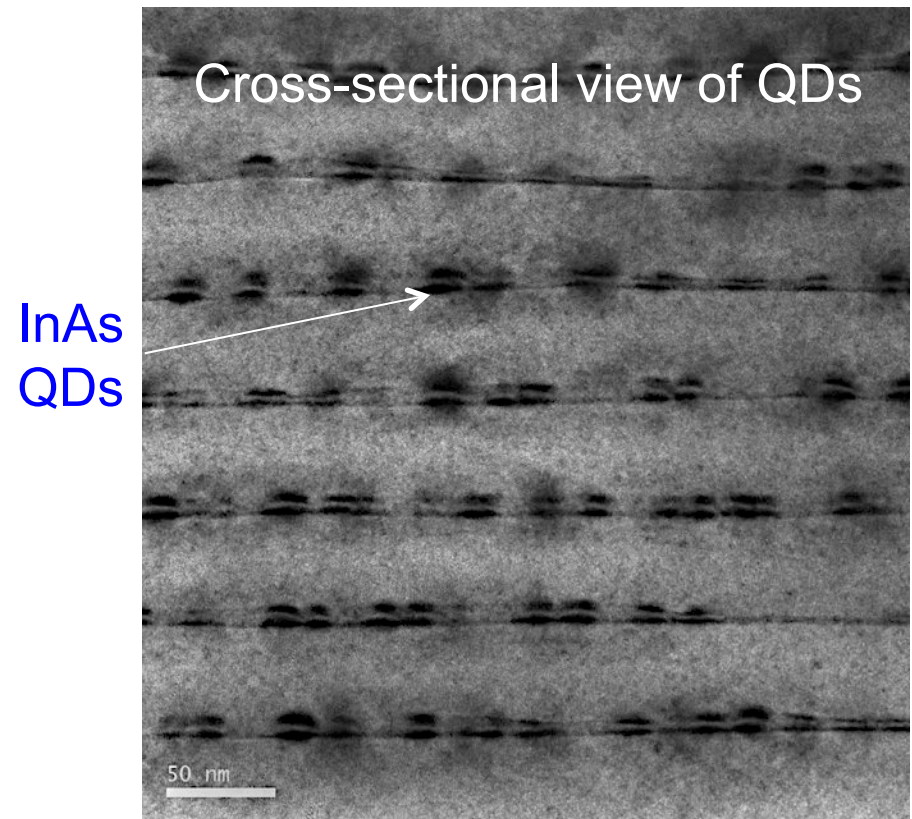
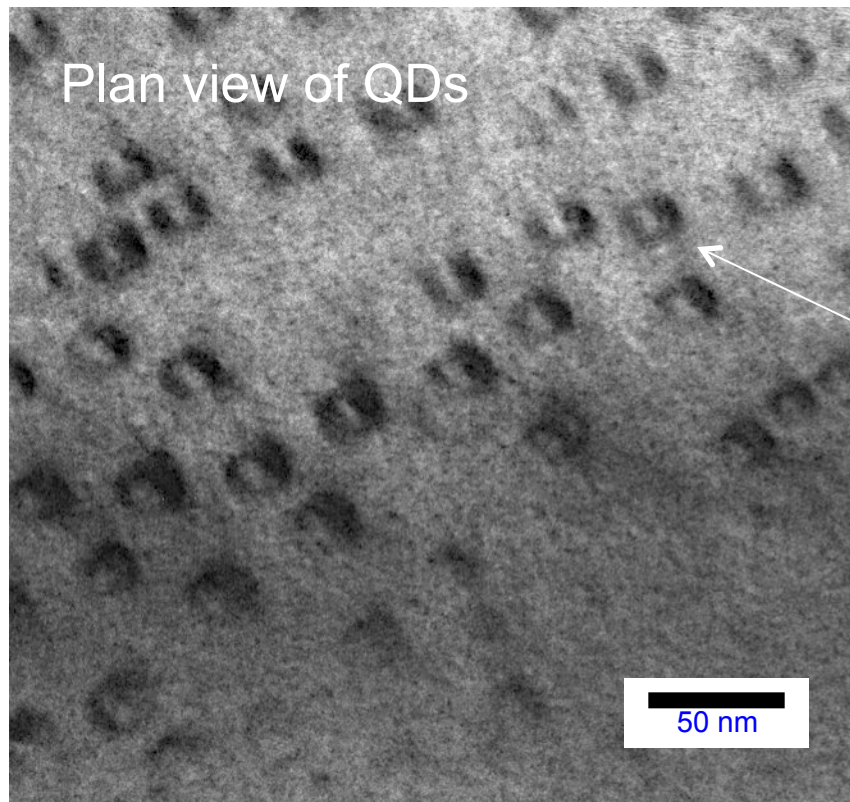
- Two graded index separate confinement heterostructure (GRINSCH) lasers were grown on GaAs-on-Ge-on-Si virtual substrates provided by IQE Inc.
- In one wafer, the QD barrier layers were p-doped with beryllium to improve  $T_0$ .



- TEM images of unprocessed laser material
- $>10^8 \text{ cm}^{-2}$  dislocation density in the QD active region

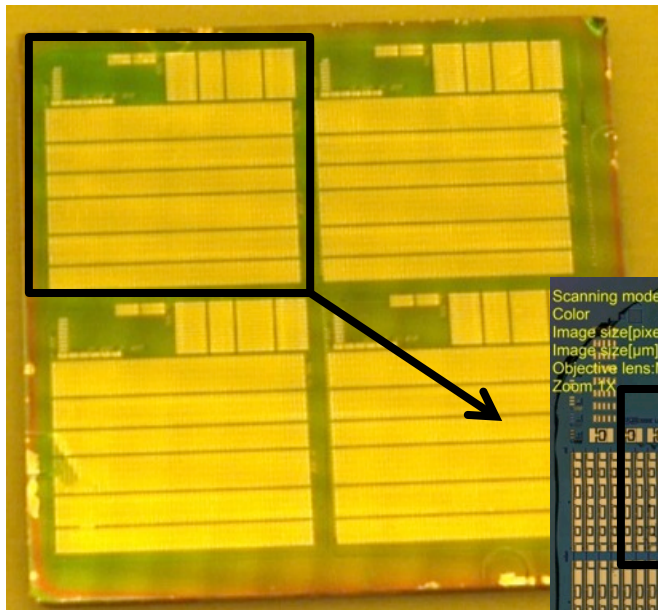


- TEM images of unprocessed laser material
- $>10^8 \text{ cm}^{-2}$  dislocation density in the QD active region

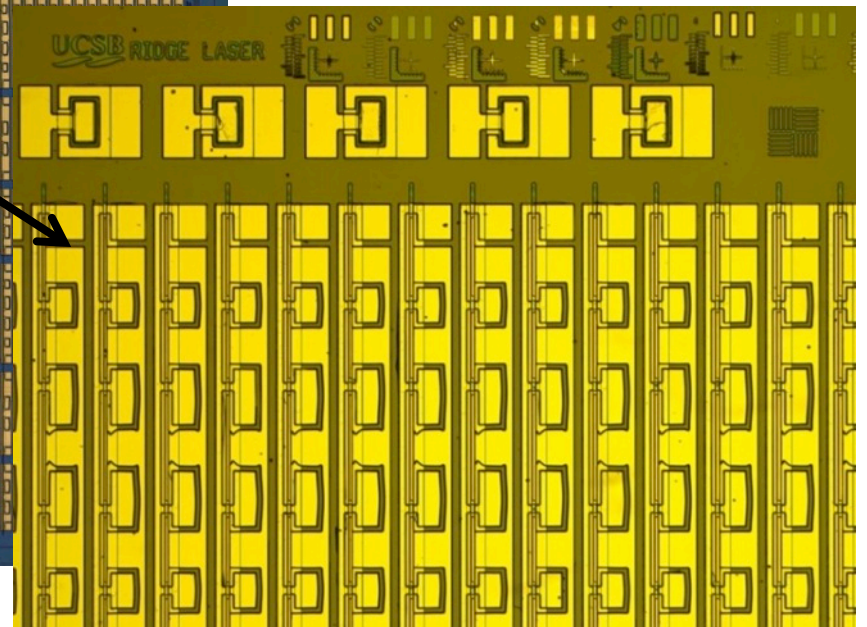
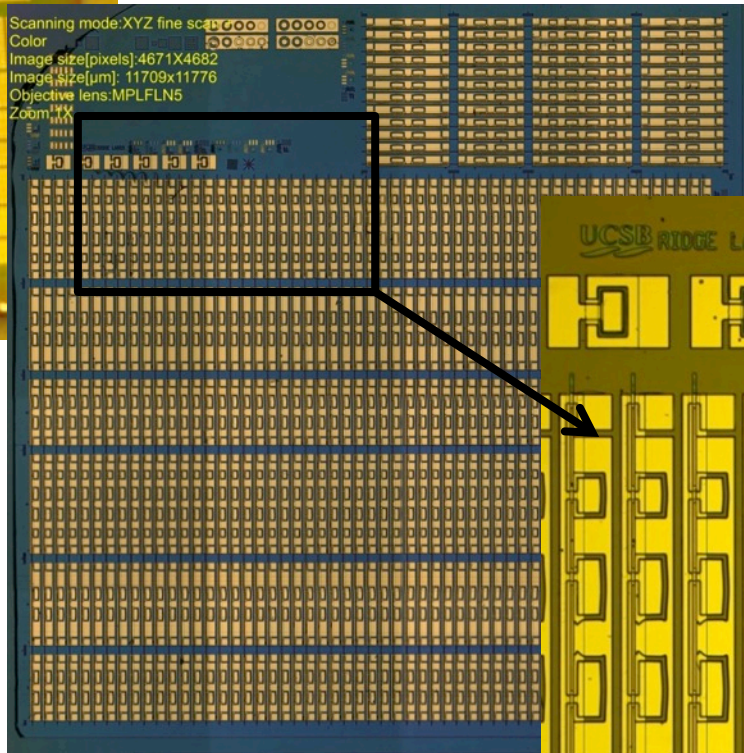




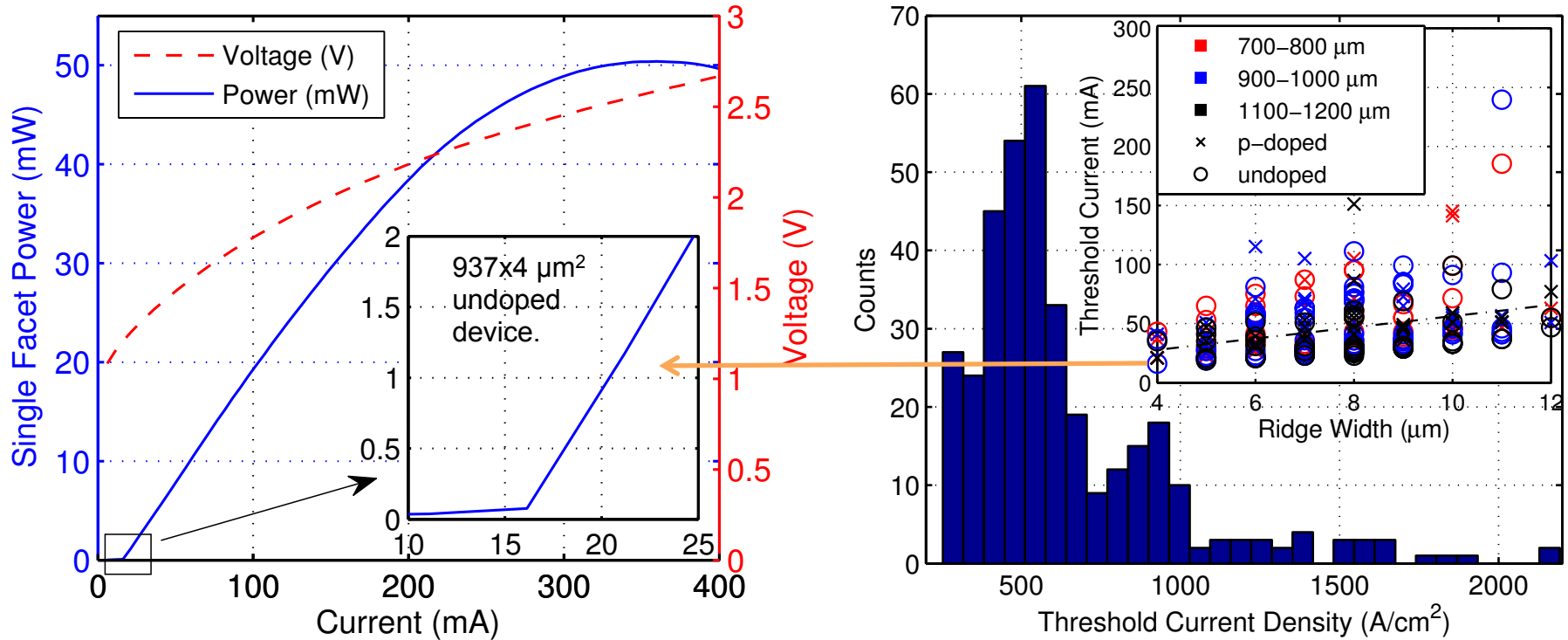
# Device Fabrication



- Epi processed into ridge lasers 4-12  $\mu\text{m}$  wide, 700-1200  $\mu\text{m}$  long cavities.
- Facets were polished, rear facet HR coated ( $\sim 95\%$ ).

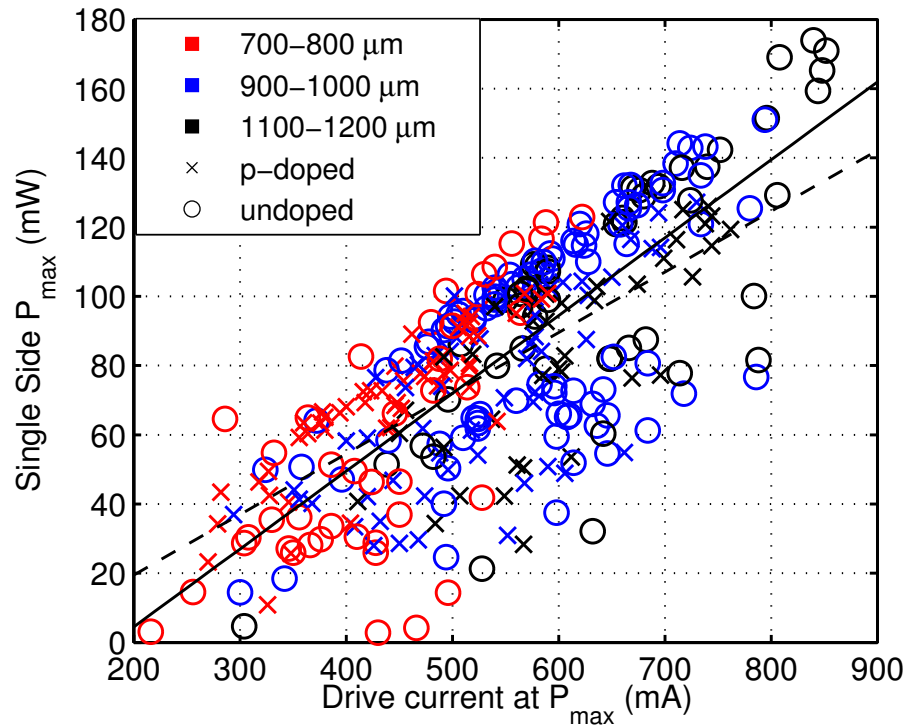


- Over 300 working lasers measured from two wafers.
- Uniform threshold current densities across die/wafers.



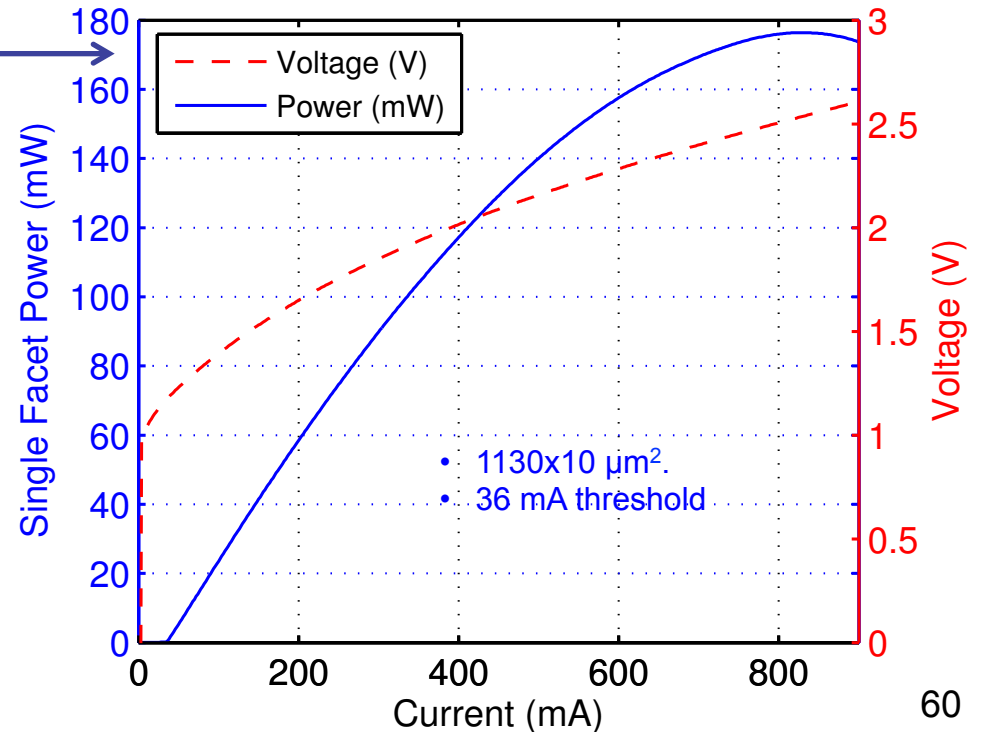
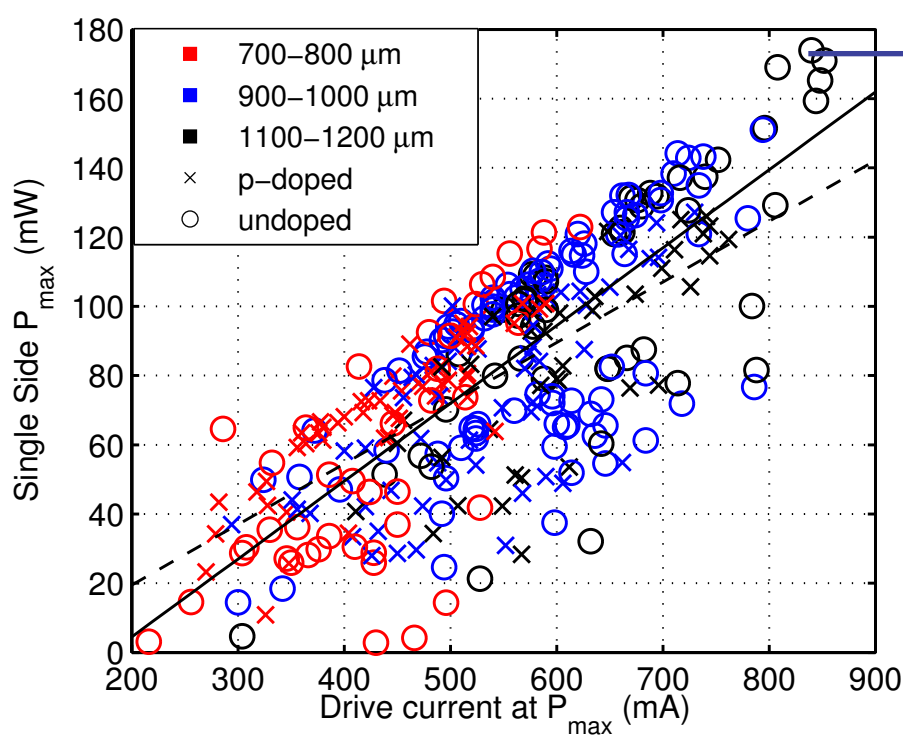
Liu, Alan Y., et al. "High performance continuous wave 1.3 μm quantum dot lasers on silicon." Applied Physics Letters 104.4 (2014): 041104.

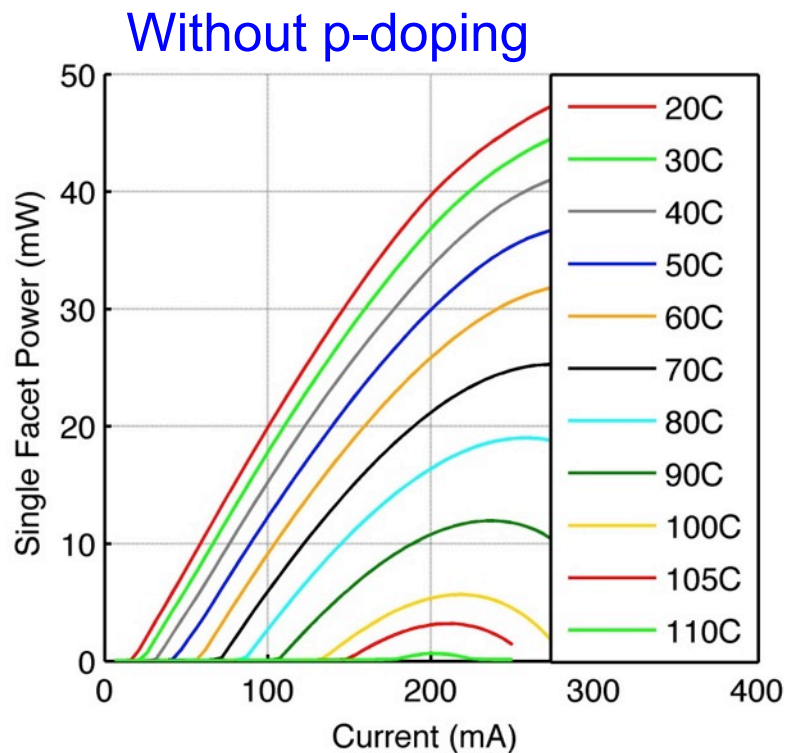
- CW powers over 100 mW routinely achieved.



# Output powers

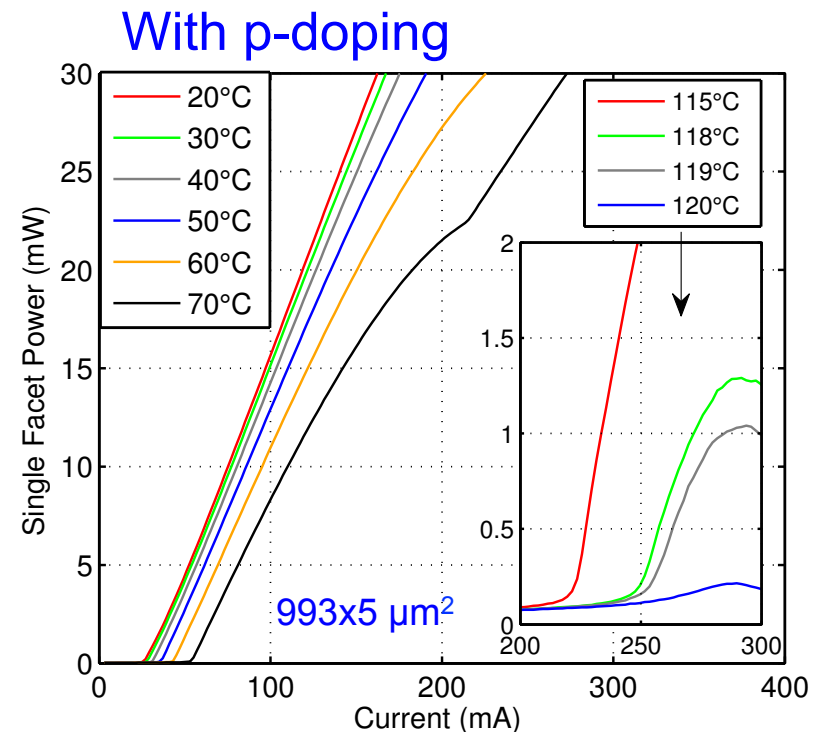
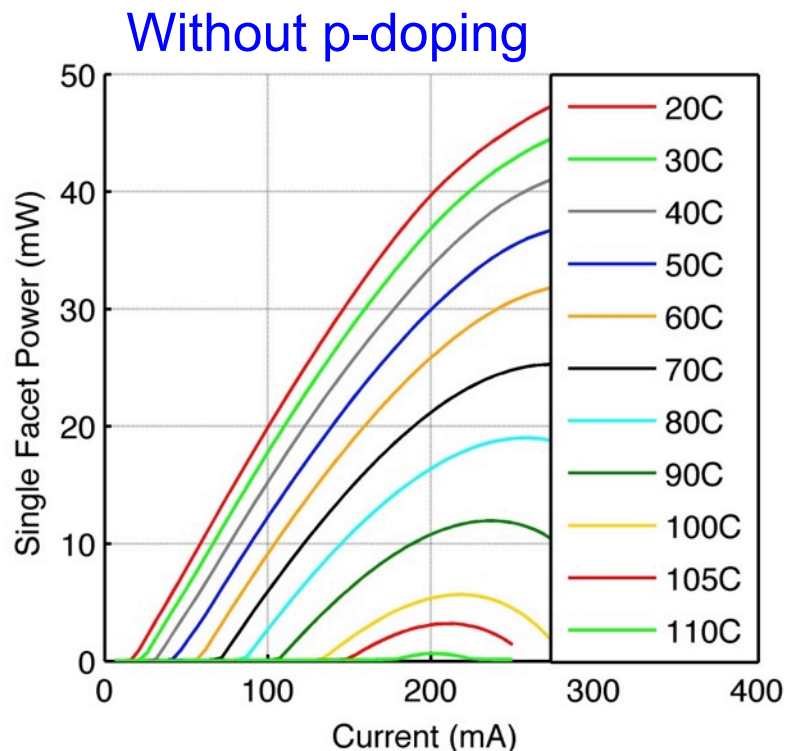
- CW powers over 100 mW routinely achieved.
- Nearly **180 mW** maximum CW single side output power at 20 °C from HR coated 1130x10  $\mu\text{m}^2$  intrinsic active region (undoped) device.
  - 33% differential efficiency and 18% WPE (at 150 mA)





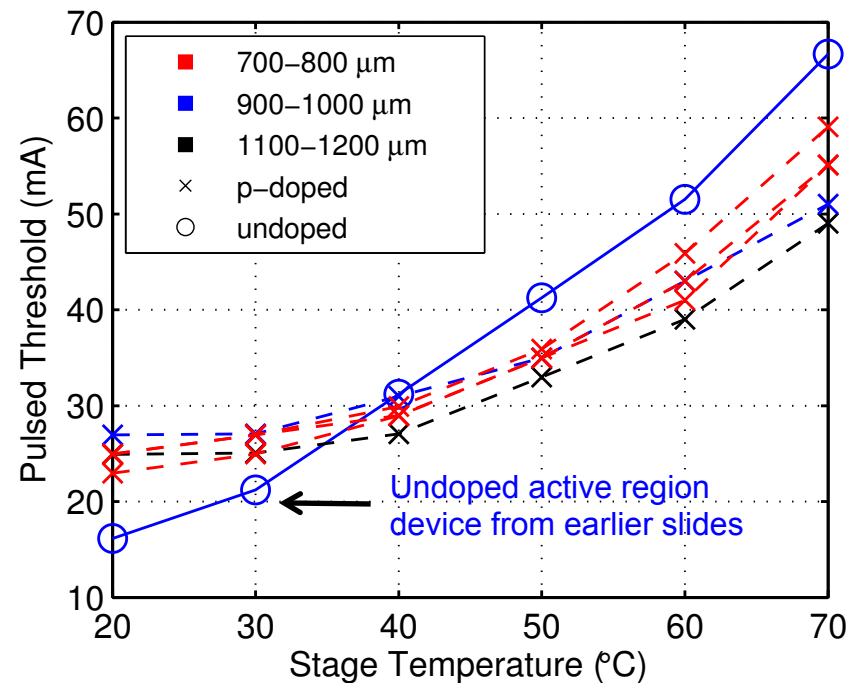
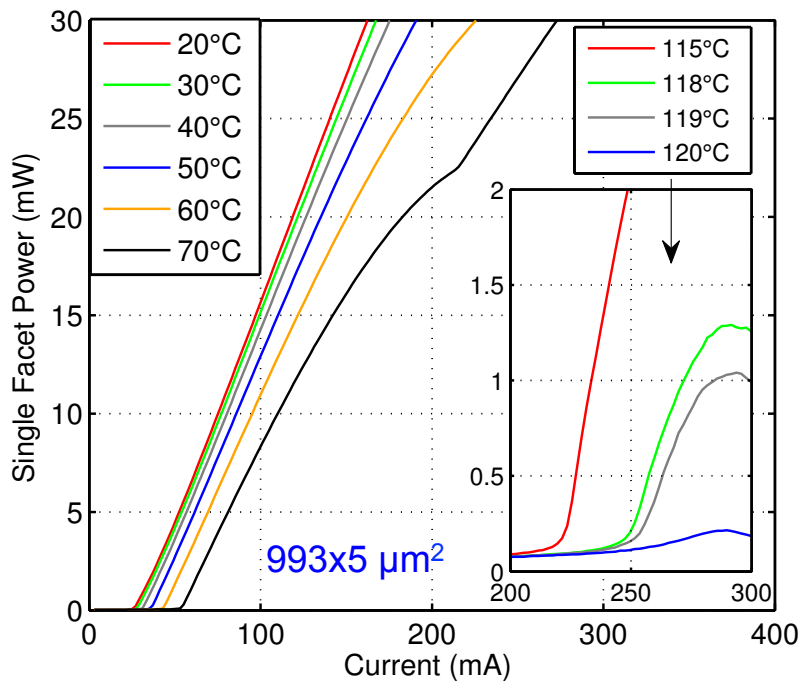
[1] Alexander, Ryan R., et al. "Systematic study of the effects of modulation p-doping on 1.3- $\mu\text{m}$  quantum-dot lasers." *Quantum Electronics, IEEE Journal of* 43.12 (2007): 1129-1139.

- P-doping the active region improves thermal performance.[1]
- Continuous wave lasing up to **119°C**
  - (dual state lasing at high currents/temperatures).



[1] Alexander, Ryan R., et al. "Systematic study of the effects of modulation p-doping on 1.3- $\mu\text{m}$  quantum-dot lasers." *Quantum Electronics, IEEE Journal of* 43.12 (2007): 1129-1139.

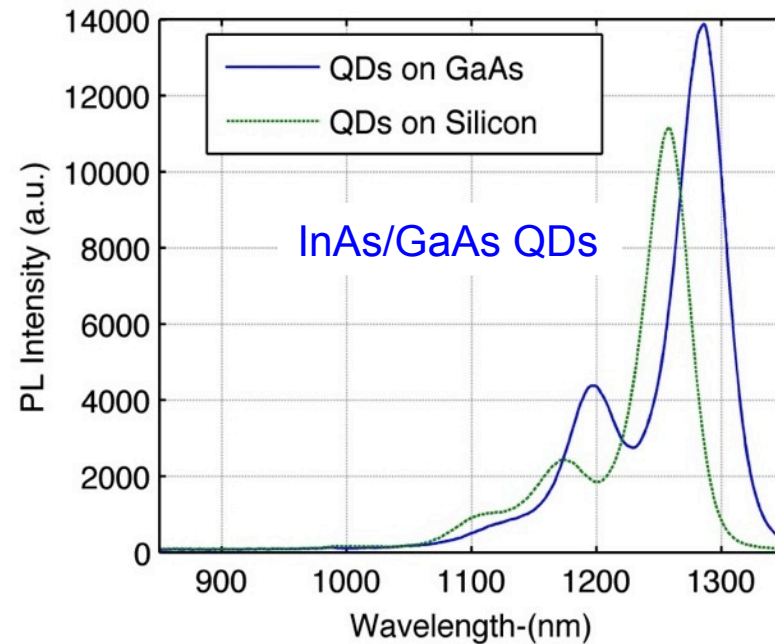
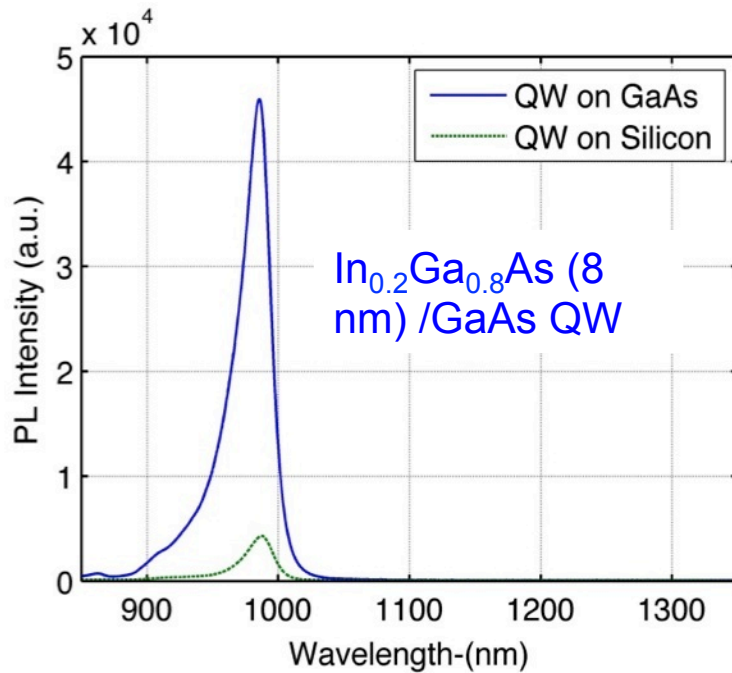
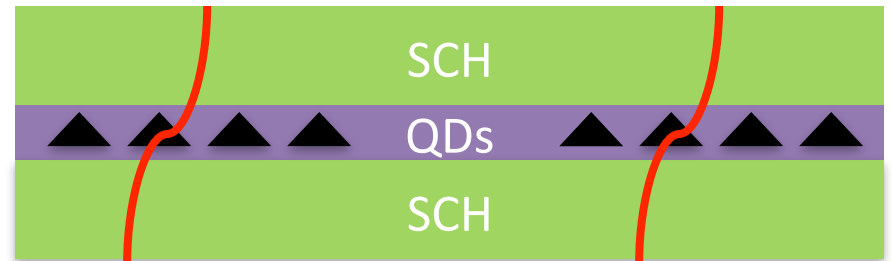
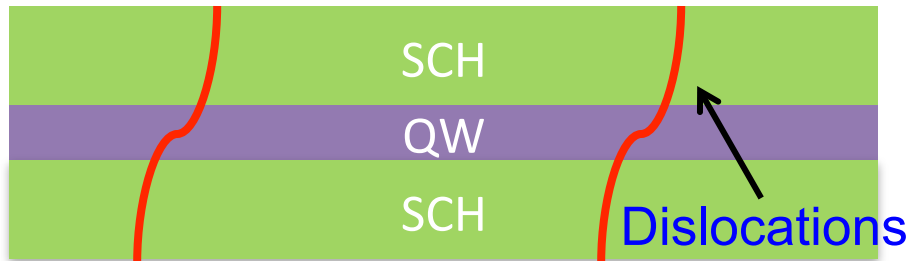
- P-doping the active region improves thermal performance.[1]
- Continuous wave lasing up to 119°C
  - (dual state lasing at high currents/temperatures).
- $T_0$  of 100-200 K from 20-40°C.



[1] Alexander, Ryan R., et al. "Systematic study of the effects of modulation p-doping on 1.3-μm quantum-dot lasers." Quantum Electronics, IEEE Journal of 43.12 (2007): 1129-1139.

# QD vs QWs on silicon

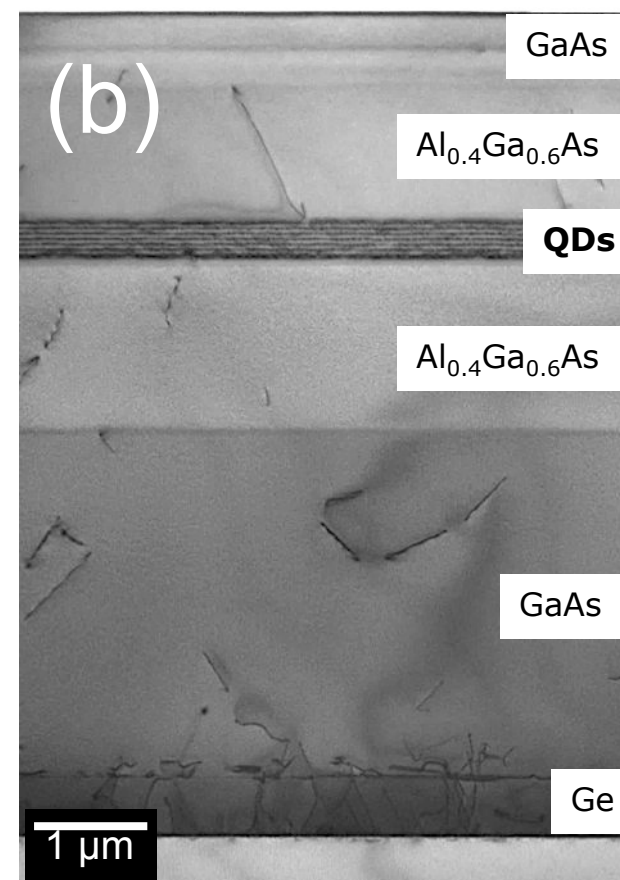
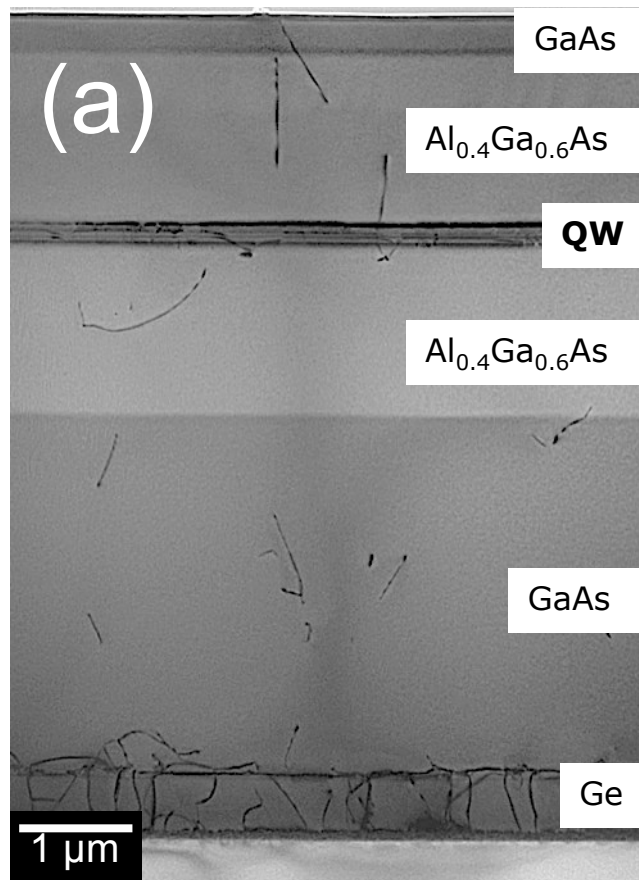
**Direct comparison:** Grow on both substrates; first quantum dots, then quantum wells Fabricate together





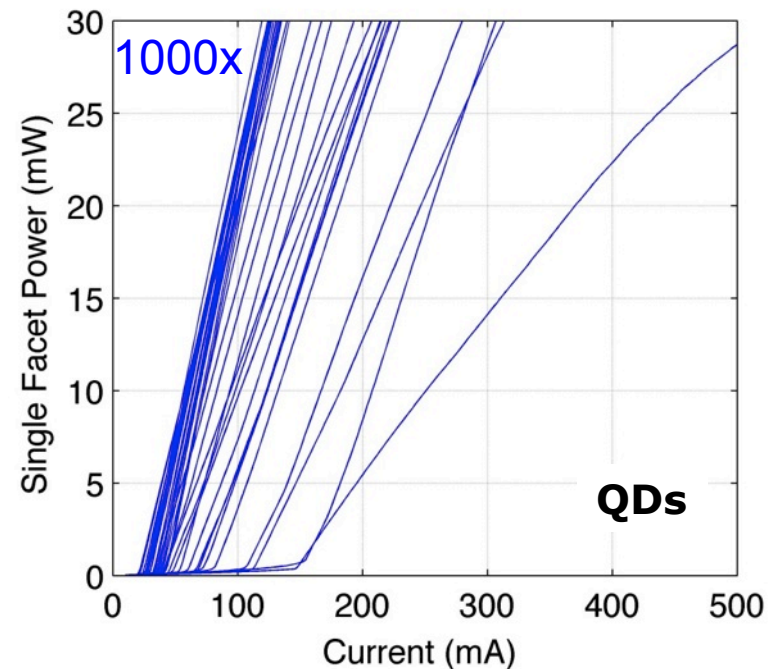
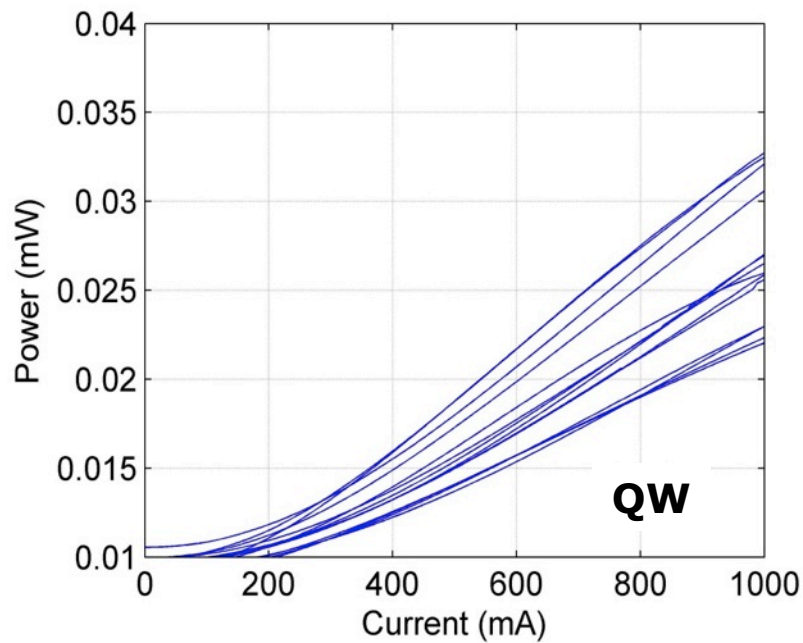
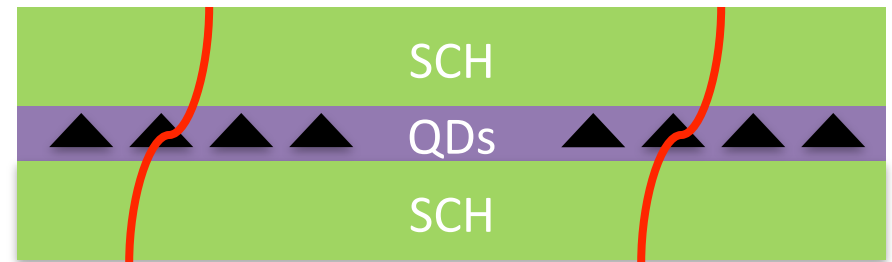
# QD vs QWs on silicon

- An  $\text{In}_{0.2}\text{Ga}_{0.8}\text{As}$  (8nm)/GaAs (3x) QW laser was grown for comparison.
- Substrate, epi stack, device design, and fabrication all identical. Only difference is active region type (QW vs QD)
- Similar dislocation density by TEM.

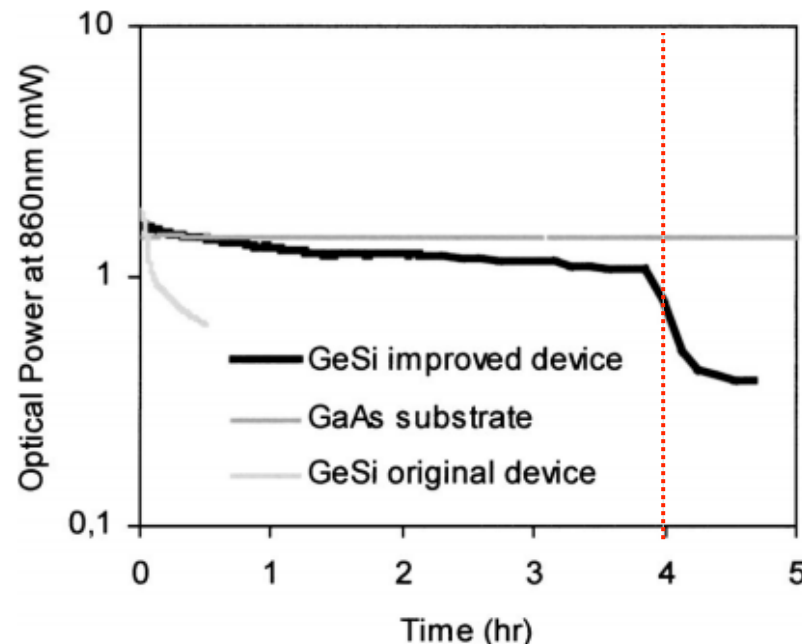
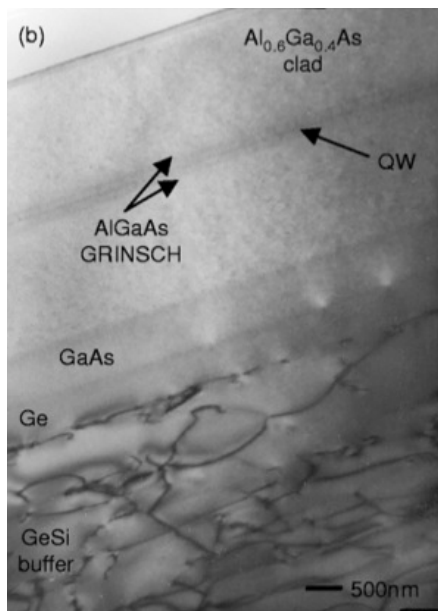


# QD vs QWs on silicon

- No lasing for QWs on Si (all LEDs).
  - Reference QW lasers on GaAs worked fine.



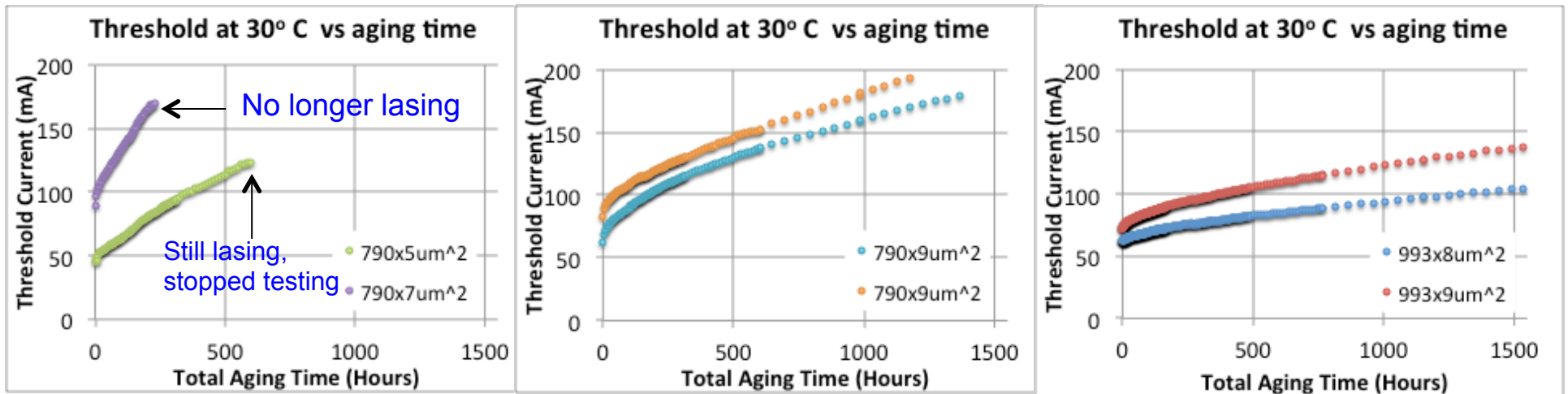
- GaAs based lasers are very sensitive to defect density and susceptible to failure by recombination enhanced defect reactions (REDR)[1][2]
- First GaAs lasers on silicon had lifetimes of **~10 seconds** (RT, pulsed) (1987) [3]
- Longest lifetime reported for GaAs based laser on Si (853 nm) is 80 hours (RT, CW) (2000) [4]
- **GaAs/AlGaAs laser on Ge/Ge<sub>x</sub>Si<sub>1-x</sub>/Si substrates: 4 hours at (RT, CW) (2003) [5]**



[5] Groenert, Michael E., et al. "Improved room-temperature continuous wave GaAs/AlGaAs and InGaAs/GaAs/AlGaAs lasers fabricated on Si substrates via relaxed graded GeSi buffer layers." *Journal of Vacuum Science & Technology B: Microelectronics and Nanometer Structures* 21 (2003): 1064.

- Stress conditions: 30°C continuous wave under constant 100 mA injection current (~1.25-3x  $I_{th}(0)$ , ~1-20 mW initial output power)
- Degradation monitored by periodic light-current-voltage (LIV) sweeps at 30 °C

Increasing cavity size/decreasing current density

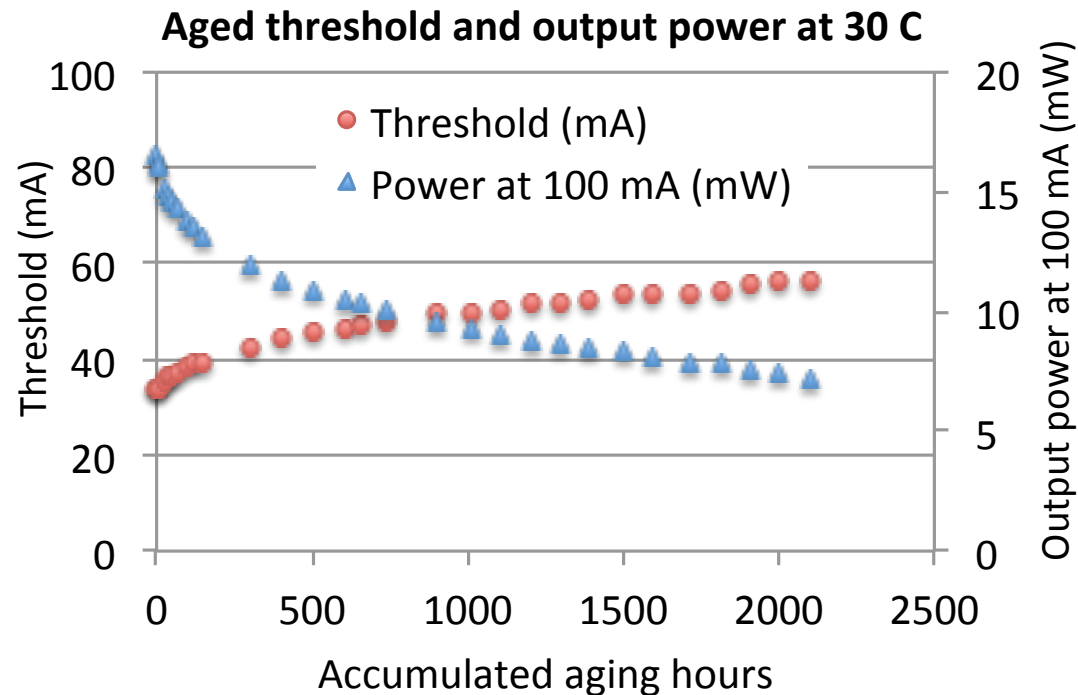


$J=1.8-2.5 \text{ kA/cm}^2$

$J=1.4 \text{ kA/cm}^2$

$J=1.1-1.2 \text{ kA/cm}^2$

- Stress conditions: 30°C continuous wave under constant 100 mA injection current ( $\sim 1.25\text{-}3\times I_{\text{th}}(0)$ ,  $\sim 1\text{-}20$  mW initial output power)
- Degradation monitored by periodic light-current-voltage (LIV) sweeps at 30 °C
- Over **2100 hours** of continuous operation (testing stopped)
  - **>26x** improvement over best reported lifetime for GaAs laser on Si:
    - (2100 hours at 30°C,  $2\text{ kA cm}^{-2}$  vs 80 hours at RT,  $1.3\text{ kA cm}^{-2}$ )
- No catastrophic failures observed.



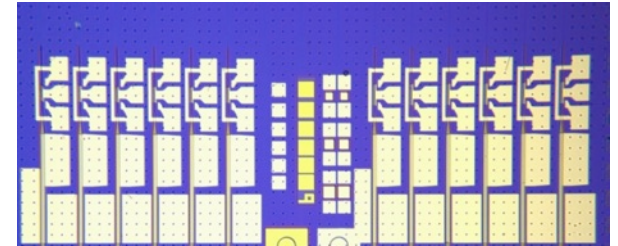
# Heterogeneously Integrated Quantum Well Transmitters

Modulators

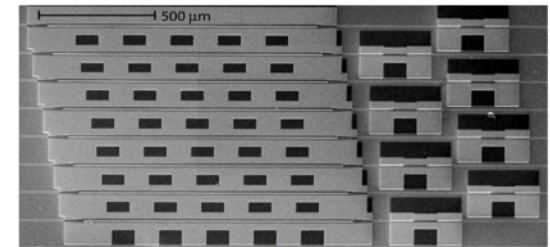
Photodetectors

Integrated Transmitters

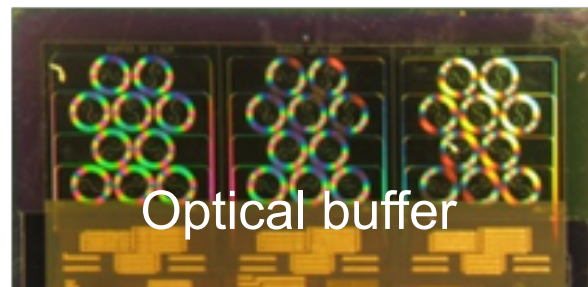
- Range of components for PICs:
  - Lasers
  - Modulators
  - Amplifiers
  - Photodetectors
- Integration
- High yield
- Good reliability



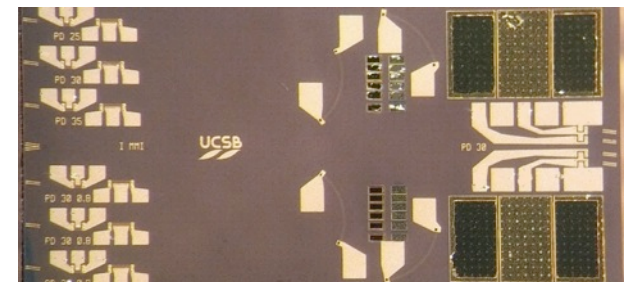
DFB/EAM/PD Array



Optical preamplifier PD array



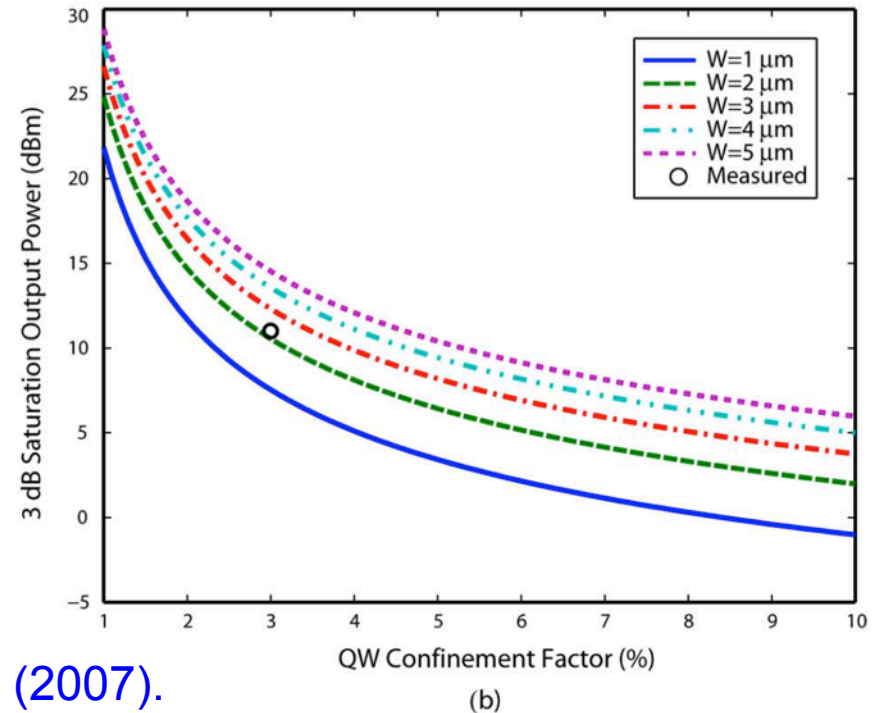
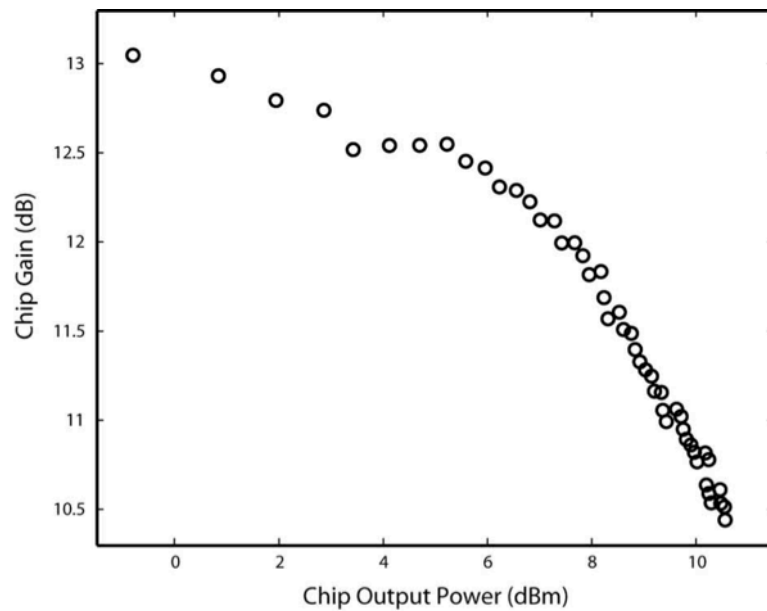
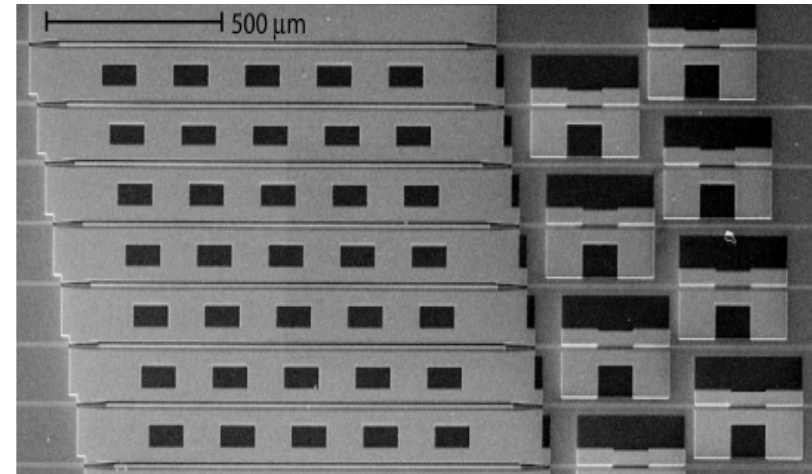
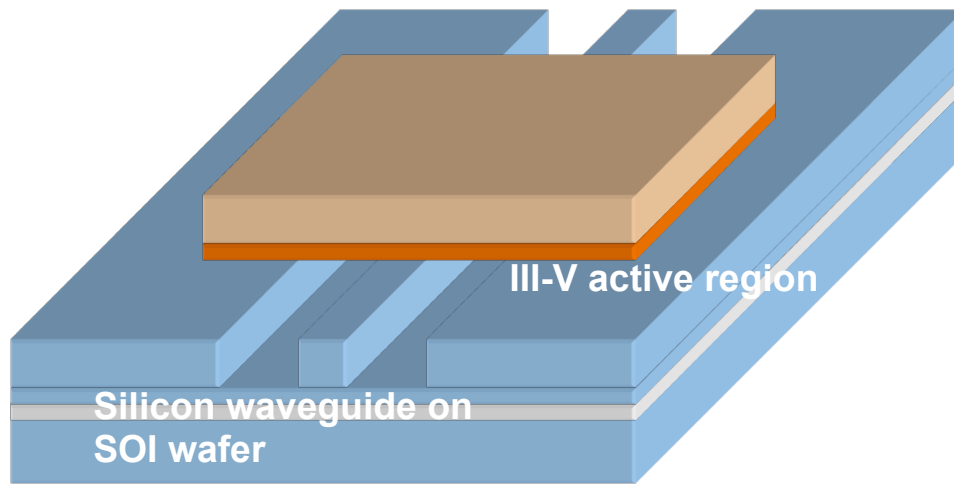
Optical buffer



DQPSK Receiver

# A Hybrid AlGaInAs–Silicon Evanescent Amplifier

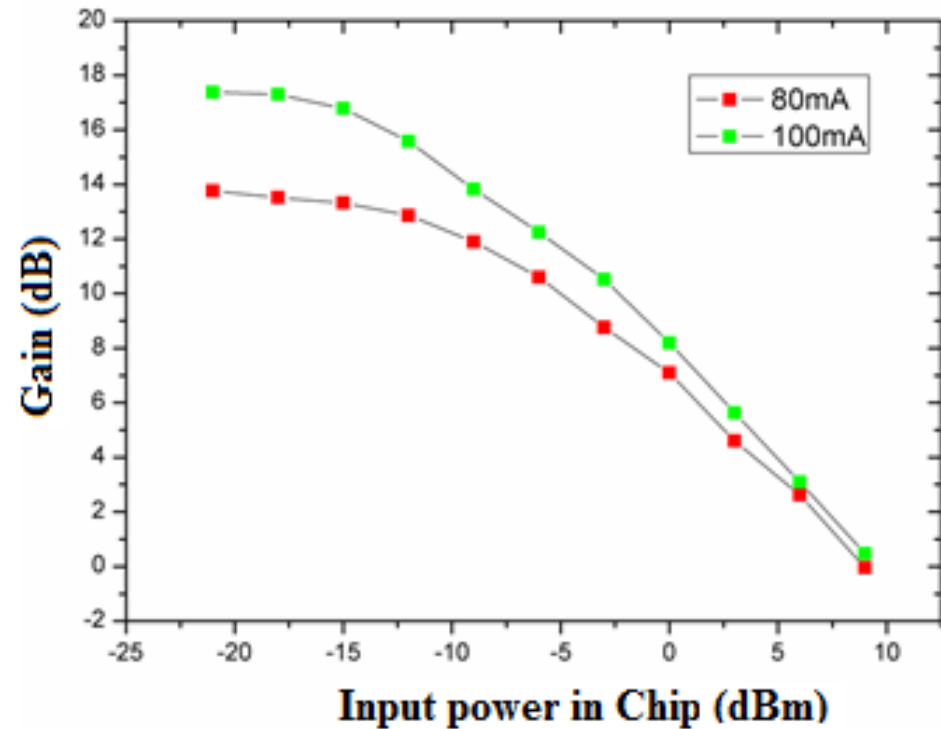
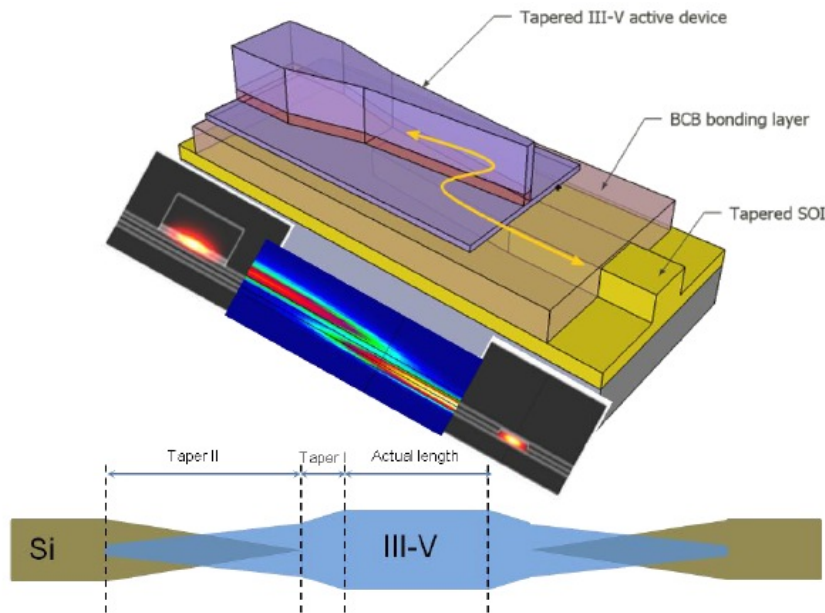
Hyundai Park, *Student Member, IEEE*, Alexander W. Fang, *Student Member, IEEE*, Oded Cohen, Richard Jones, *Member, IEEE*, Mario J. Paniccia, *Senior Member, IEEE*, and John E. Bowers, *Fellow, IEEE*



H. Park et al., PTL, 19(4), 230, February (2007).



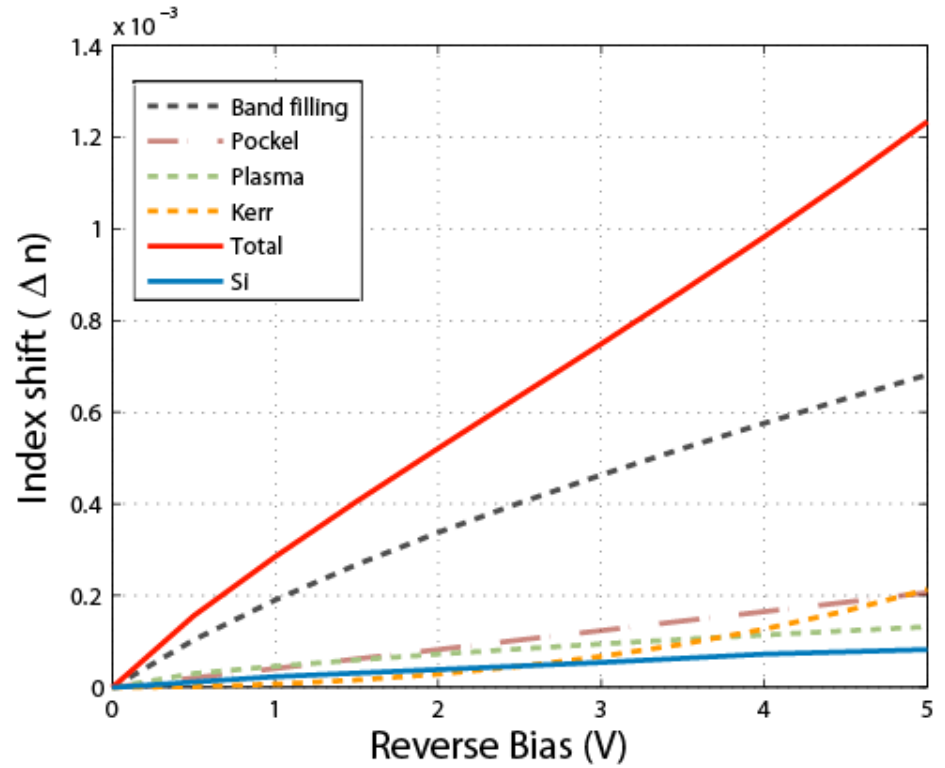
# III-V on silicon optical amplifiers



18dB small signal gain for 100mA drive current

# Hybrid Silicon Switch: Use III-V Material

p contact	P <sup>+</sup> InGaAs
Cladding	P InP
SCH	n <sup>-</sup> AlGaInAs
QW	n <sup>-</sup> AlGaInAs
SCH	n <sup>+</sup> AlGaInAs
n contact	n <sup>+</sup> InP



$\text{Si} = \text{Plasma} + \dots$   
 $\text{III-V} = \text{Plasma} + \text{BF} + \text{Pockels} + \text{Kerr} + \dots$

*Note: A green arrow indicates that the III-V contribution is >10x greater than the Si contribution.*

\* Silicon phase shift is calculated from “High speed optical modulation based on carrier depletion in a silicon waveguide,” A. Liu et. al, Opt. Express, 15 (2), 2007

# Hybrid Silicon MZMs

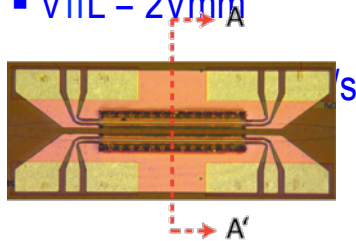


### Gen 1 Hybrid silicon MZM:

- AlGaInAs QW
- Coplanar waveguide
- QW undercut

### Performance:

- 8 GHz bandwidth
- $V_{\pi L} = 2V\text{mm}$



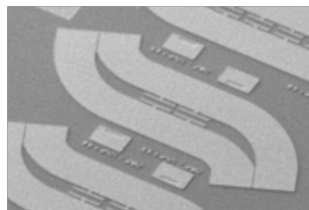
H. Chen, et al., OE 16(25), 20571(2008)

### Gen 2 Hybrid silicon MZM:

- Capacitively-loaded slot line
- Electric-isolation by Implantation
- Push-pull operation

### Performance:

- ~12.5 GHz bandwidth
- 11 dB ER @ 25 Gb/s



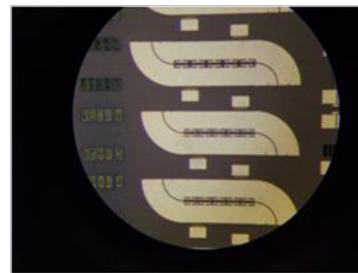
H. Chen, et al., OE 18(2), 1070(2010)

### Gen 3 Hybrid silicon MZM:

- Improved implantation profile
- Improved contact resistance
- Improved MMI

### Performance:

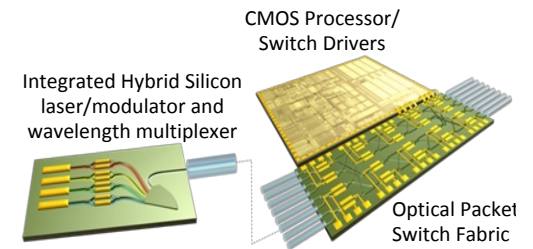
- 27 GHz bandwidth
- 11 dB ER @ 40 Gb/s



H. Chen, et al., OE 19(2), 1455(2011)

### Application:

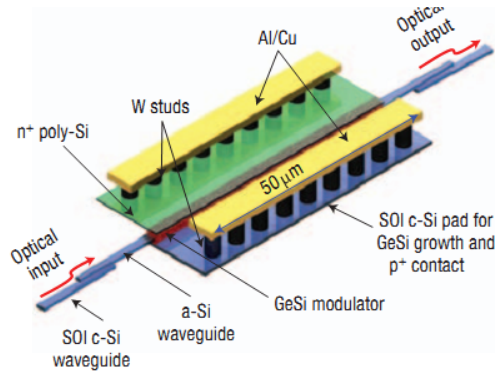
- large scale non blocking optical switch array
- Vector-modulated Tx



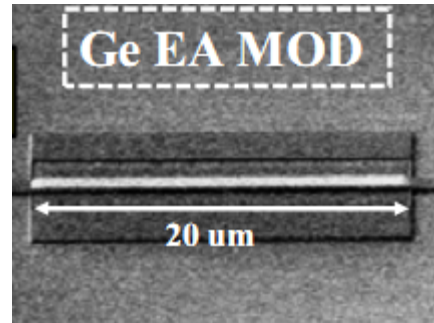
L. Chen et al., Photonic J. 2011



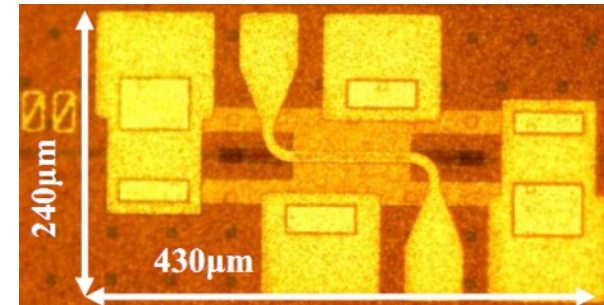
$$T = \exp\left(-\alpha_0 L - \underbrace{\alpha(V)}_{\text{voltage-controlled loss}} L\right)$$



Liu, et al., Nat. Photonics, 2, 433-437, 2008



Lim, S\*STAR, OFC OWQ2, 2011



Tang, et al., OE, 19(7), 5811-5816 (2011)

Group	$f_{3dBc}$ [GHz]	Len [ $\mu\text{m}$ ]	ER [dB  $V_{pp}$  Gb/s]	Type	Note
Liu, MIT, 2008	1.2	50	--	GeSi	Frank-Keldysh
Rong, Stanford, 2010	13	30	0.53 2.5 3.125	GeSi/Si	QCSE, $\lambda=1408\text{nm}$
Tang, UCSB, 2011	74	100	9.8 2 50	AlGaInAs	QCSE, hybrid
Lim, A*STAR, 2011	--	100	-- -- 1.25	Ge	FK, $\lambda=1600\text{nm}$

# Hybrid Si Electroabsorption Modulators

2008

2011

2012

2013-2014

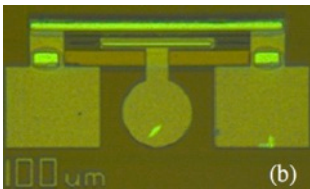
Gen 1 Hybrid silicon EAM:

- AlGaInAs QW
- Lumped electrode
- QW undercut

Performance:

- >16 GHz bandwidth
- sub-voltage operation

(250 $\mu$ m)



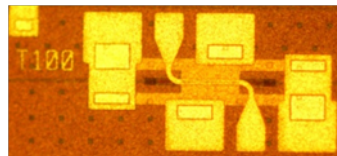
Y. Kuo, et al., OE 16(13), 9936 (2008)

Gen 2 Hybrid silicon EAM:

- Distributed electrode
- Electrically-isolated taper
- Improved contact resistance

Performance:

- ~42 GHz bandwidth
- 9.8 dB ER @ 50 Gb/s



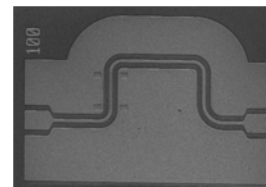
Y. Tang, et al., OE 19(7), 5811(2011)

Gen 3 Hybrid silicon EAM:

- New epitaxy design for 1300 nm
- Segmented electrode
- Gradually-doping p-InP

Performance:

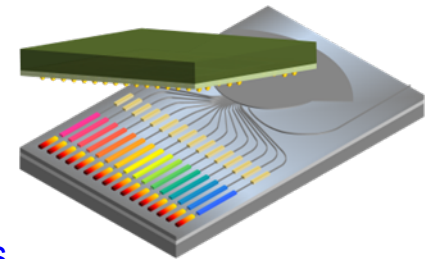
- bandwidth > 67 GHz
- modulation efficiency > 5 dB/V
- power consumption < 1mW/Gb/s
- transmission distance > 10km



Y. Tang, et al., OE 20(10), 11529(2012)

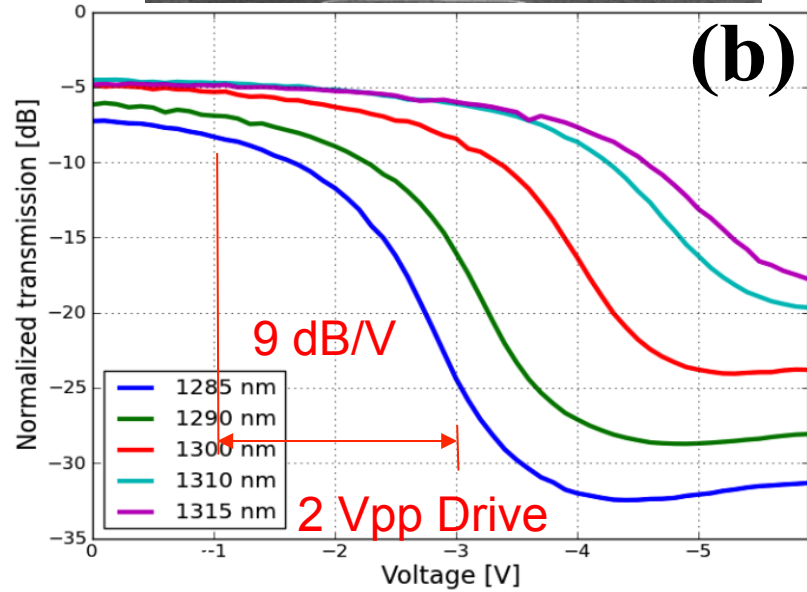
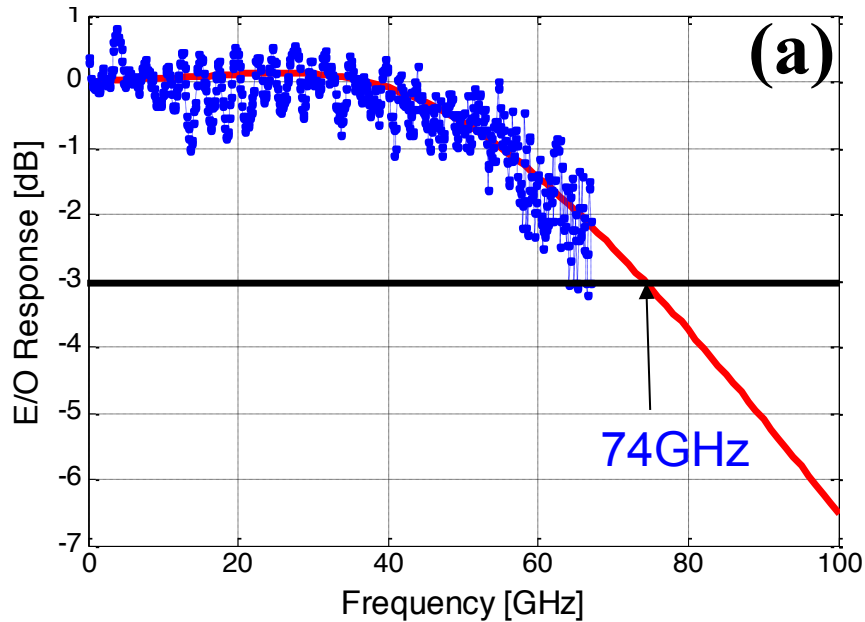
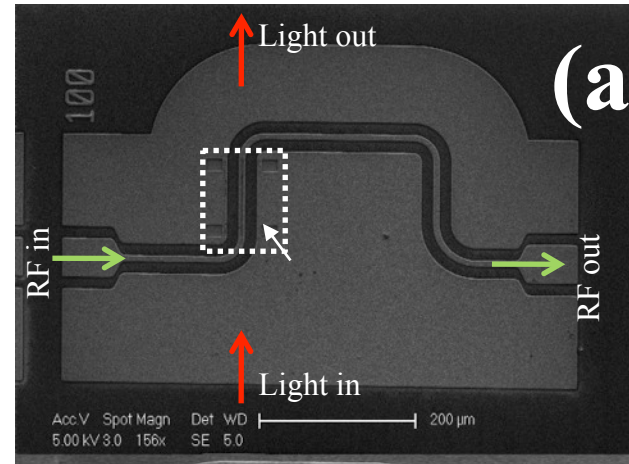
Gen 4 Hybrid silicon EAM:

- 1x16 EML Array+Mux
- <1pJ/bit @ 25Gb/s



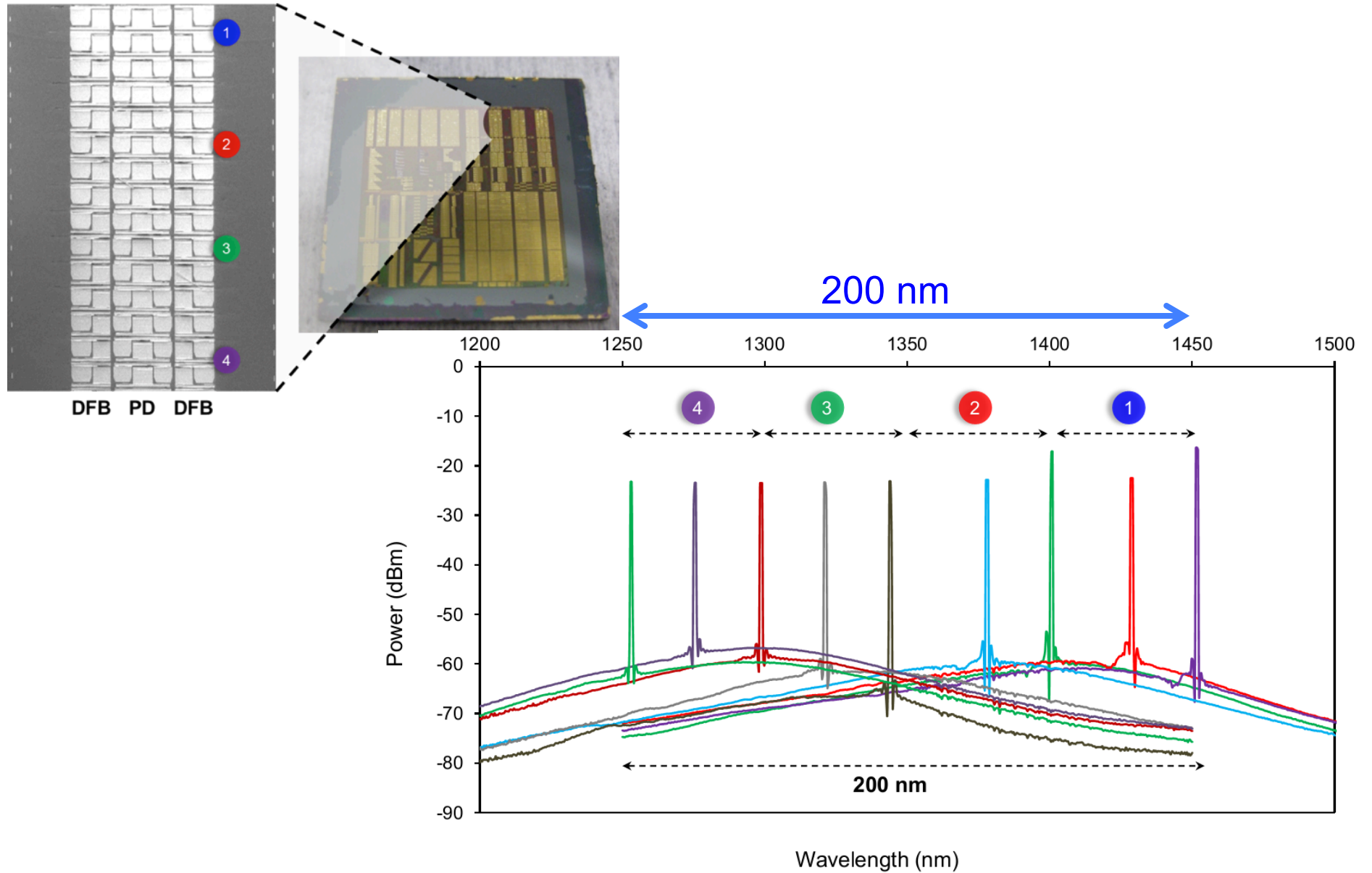
# Hybrid Silicon HSEAM

- Segmented electrode
- Length: 100  $\mu\text{m}$
- >67 GHz Bandwidth



**330 fJ/bit**

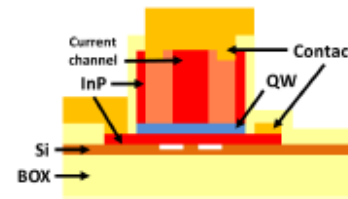
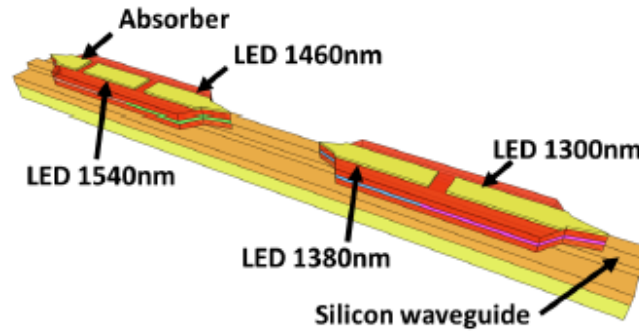
# Integrated Transmitters



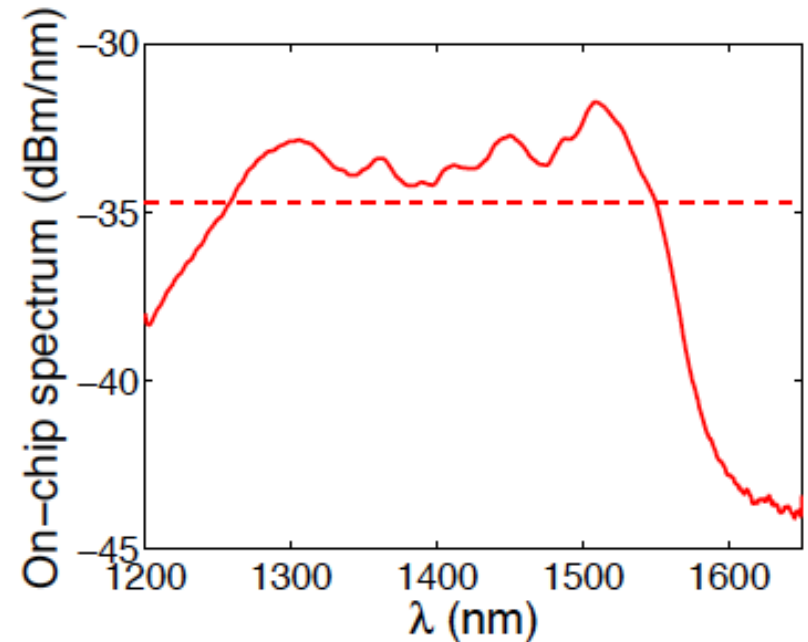
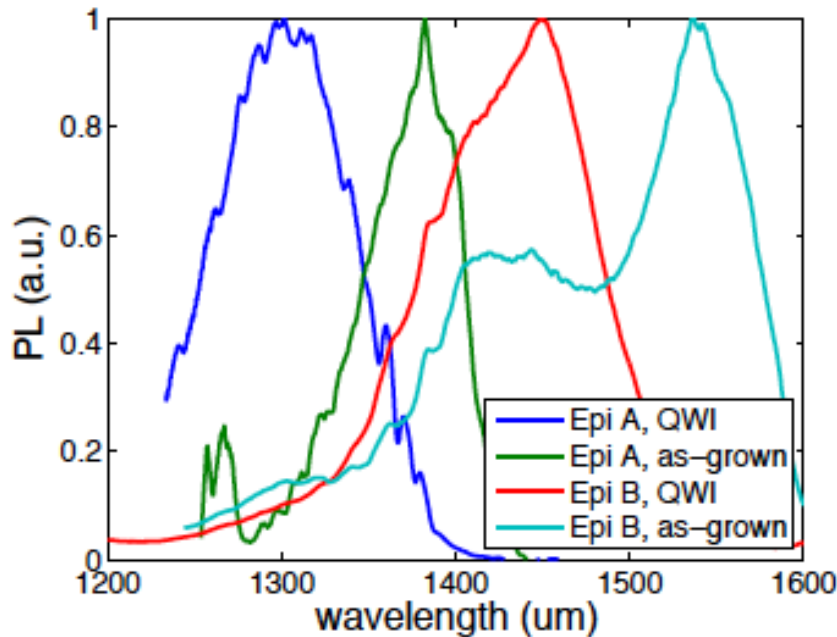
# Heterogeneously integrated III-V on silicon multi-bandgap superluminescent light emitting diode with 290nm optical bandwidth

Optics Letters 2014

A. De Groot<sup>1,2,\*</sup> J.D. Peters,<sup>1</sup> M.L. Davenport,<sup>1</sup> M.J.R. Heck,<sup>1</sup> R. Baets,<sup>2</sup> G. Roelkens,<sup>2</sup> and J.E. Bowers<sup>1</sup>



(b) Cross section of the III-V on silicon

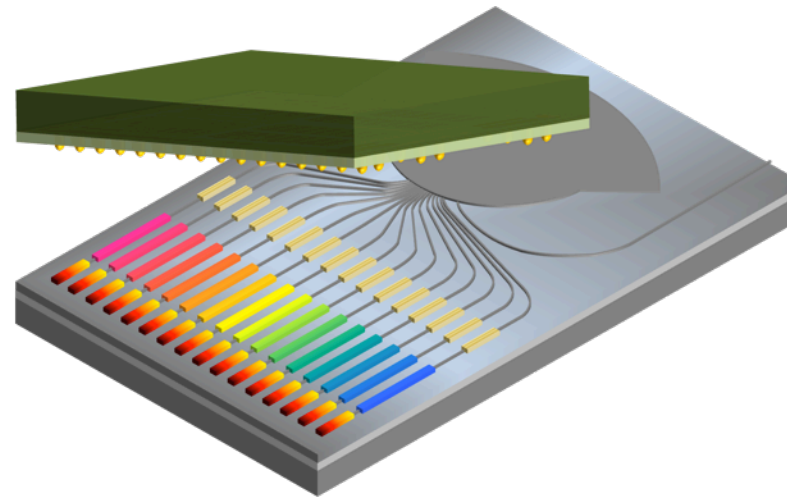
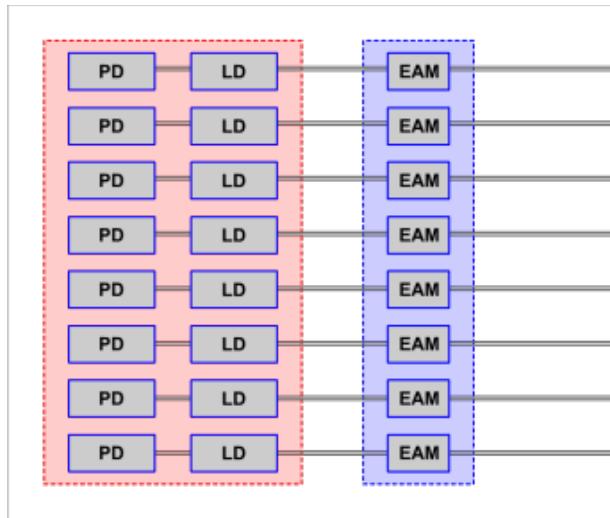




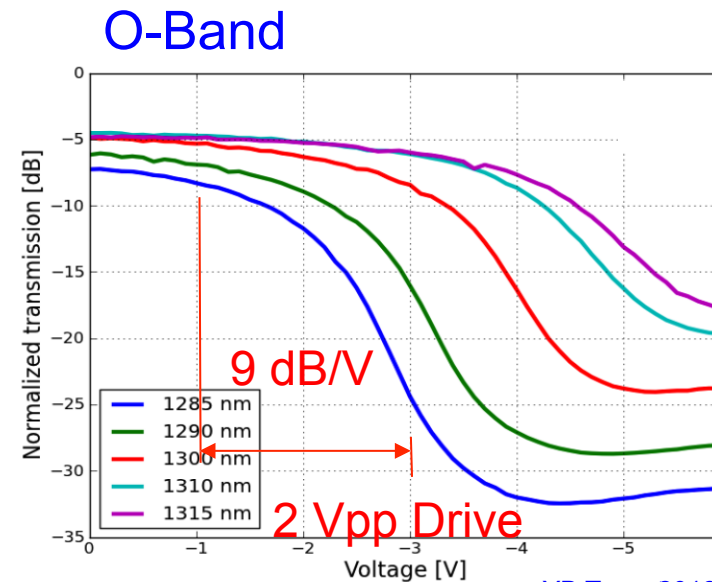
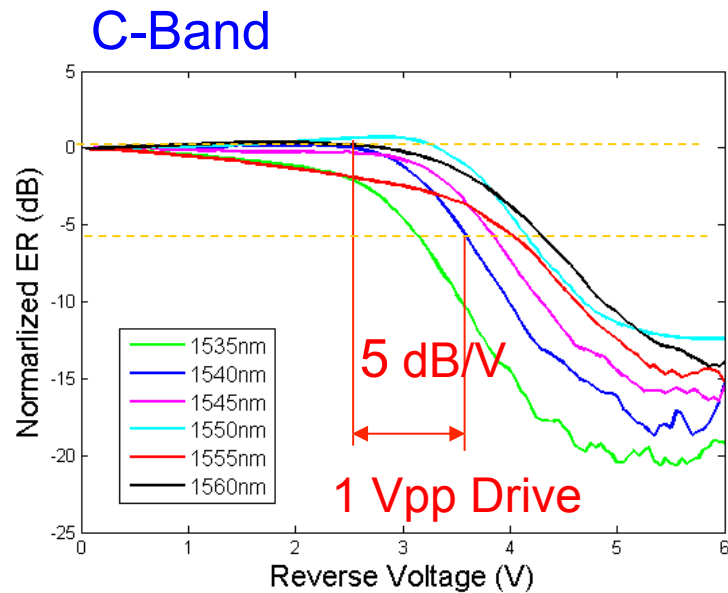
# Integration of DFB and EAM on hybrid silicon platform

Low power, high speed, integrated photonic transmitter based on hybrid silicon platform

- High capacity optical interconnects between processors and memory.
- Low power optical transmitters with high impedance modulators  
Integrate arrays of lasers with arrays of modulators to reduce the power required for off-chip lasers.
- Flip chip bonding with CMOS driver chip \*

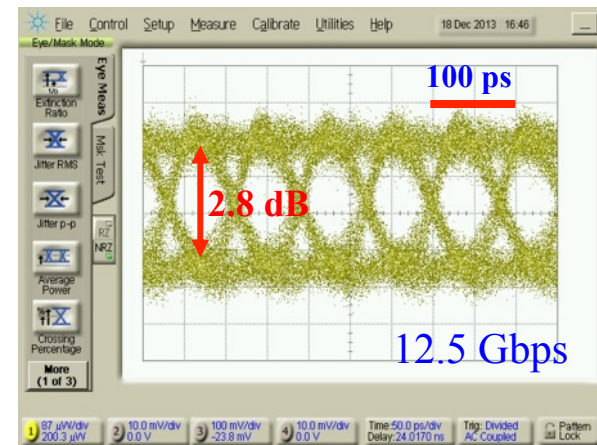
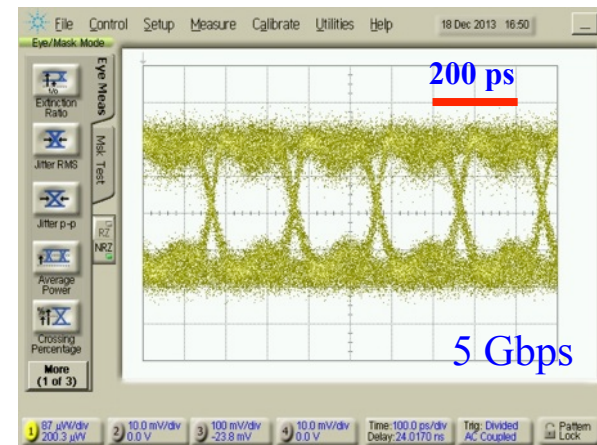
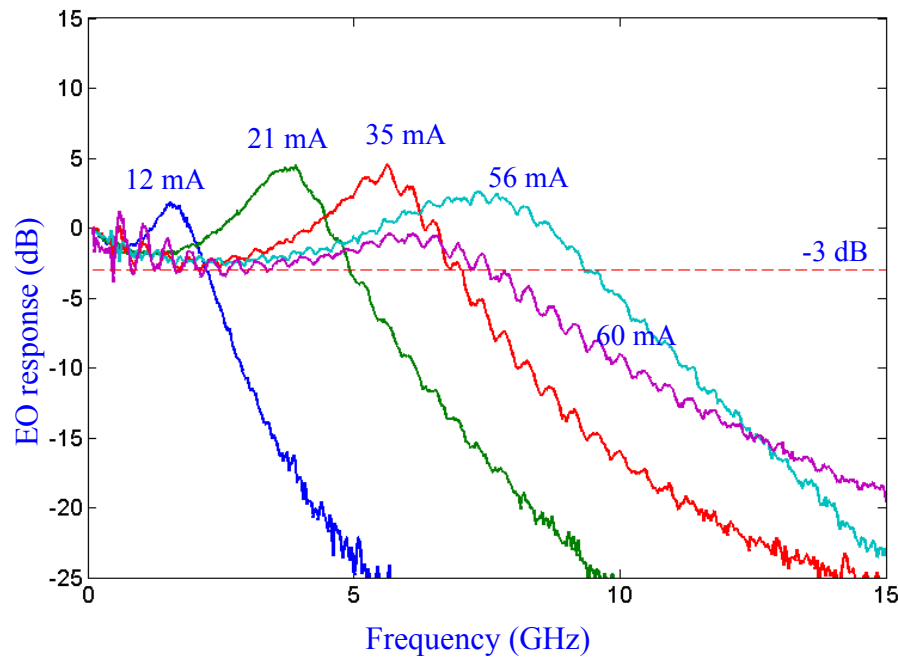


	C-band Lumped EAM	O-band Lumped EAM
Wavelength [nm]	1550	1300
Active Length [ $\mu\text{m}$ ]	100	100
Bandwidth [GHz]	18	30
ER [dB/1V]	> 5	> 9
Footprint [ $\mu\text{m}^2$ ]	55 $\times$ 220	210 $\times$ 310
Insertion Loss	3	5
Current under bias [mA]*	< 0.1	~ 0.1



# UCSB Direct modulation of short cavity DFB

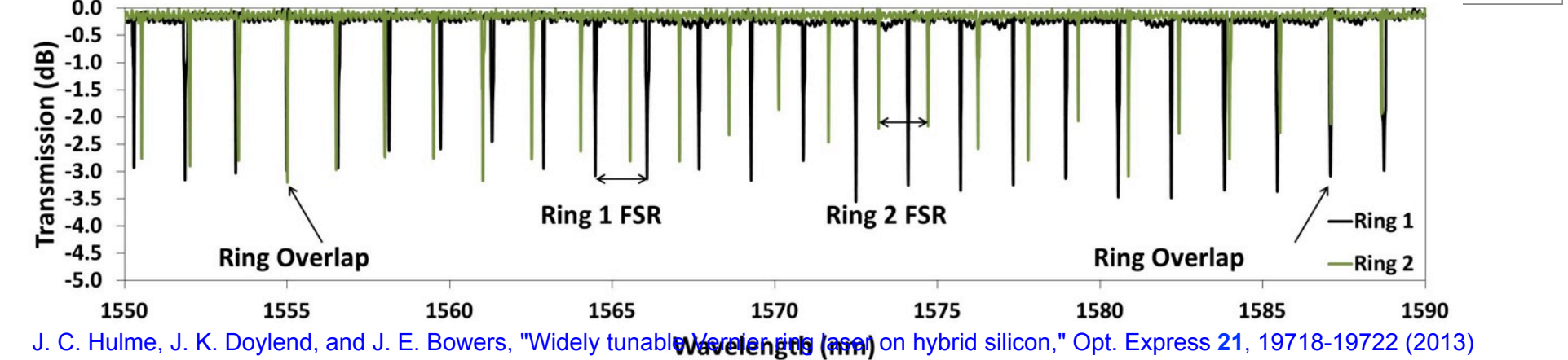
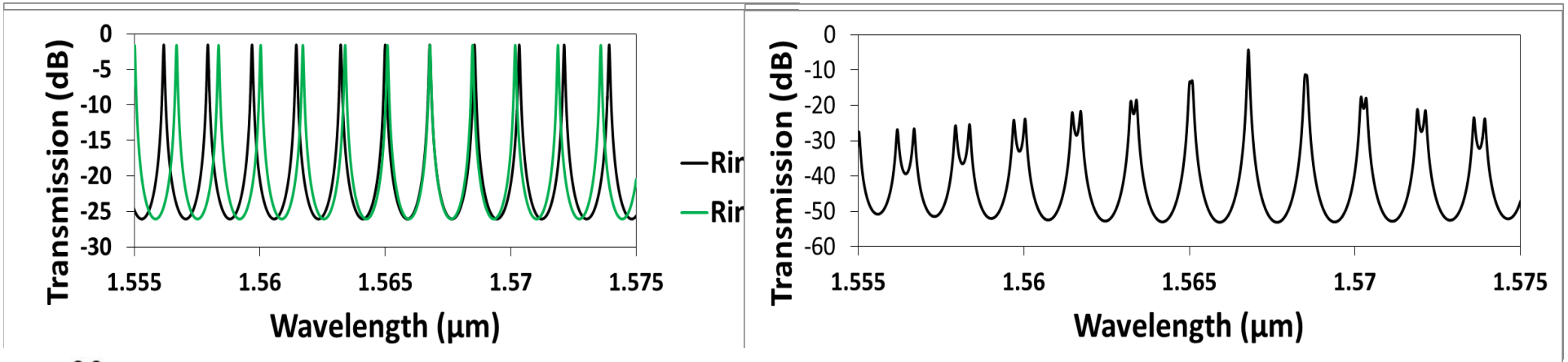
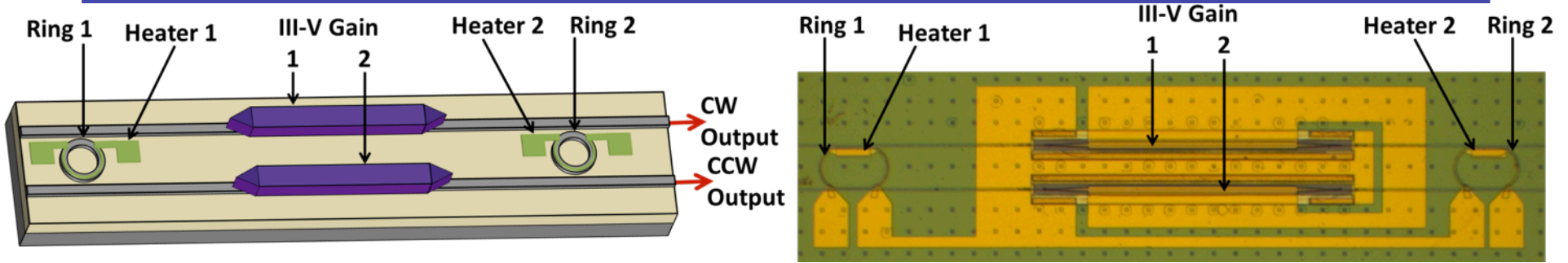
- Maximum 3 dB bandwidth is about 9.5 GHz
- The slope of  $f_r$  curve is about  $1.185 \text{ GHz/mA}^{1/2}$
- Open eye diagrams up to 12.5 Gbps.



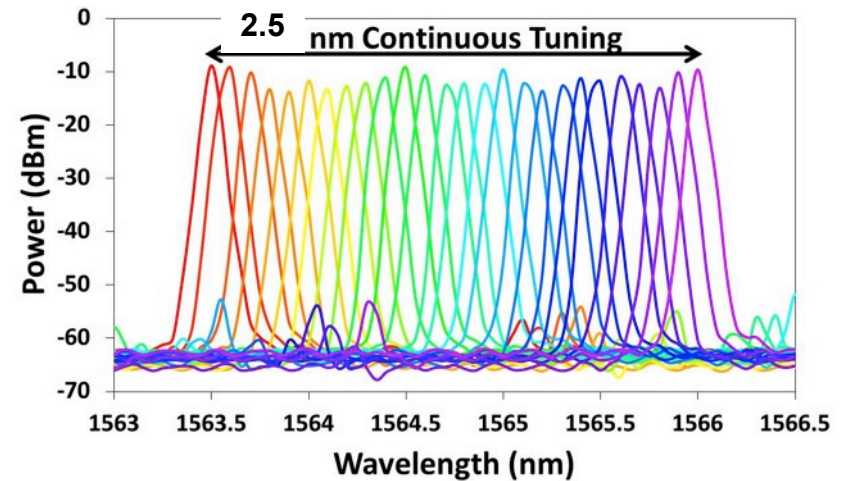
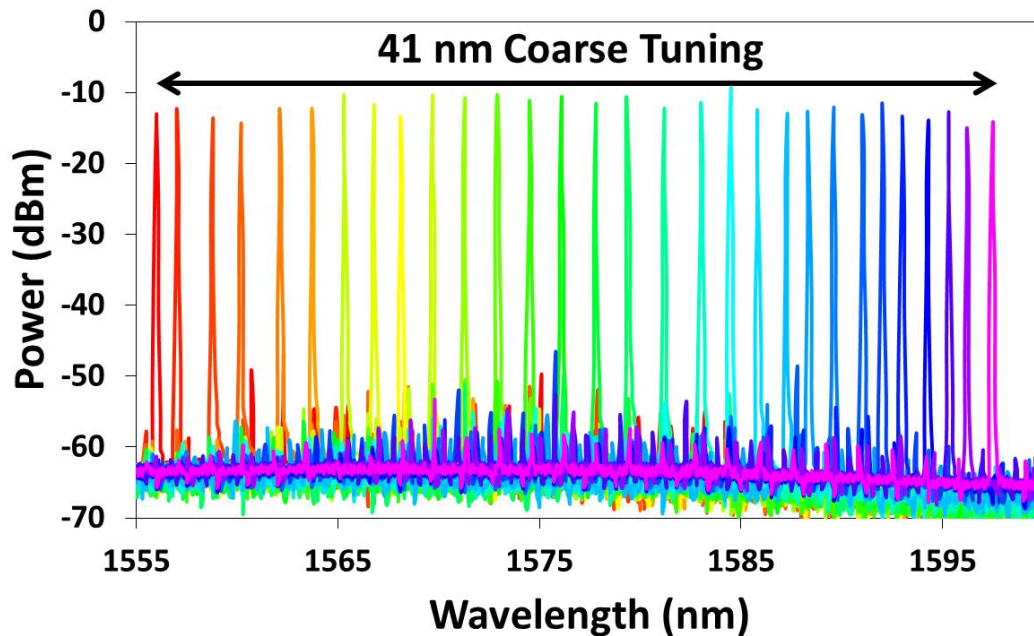
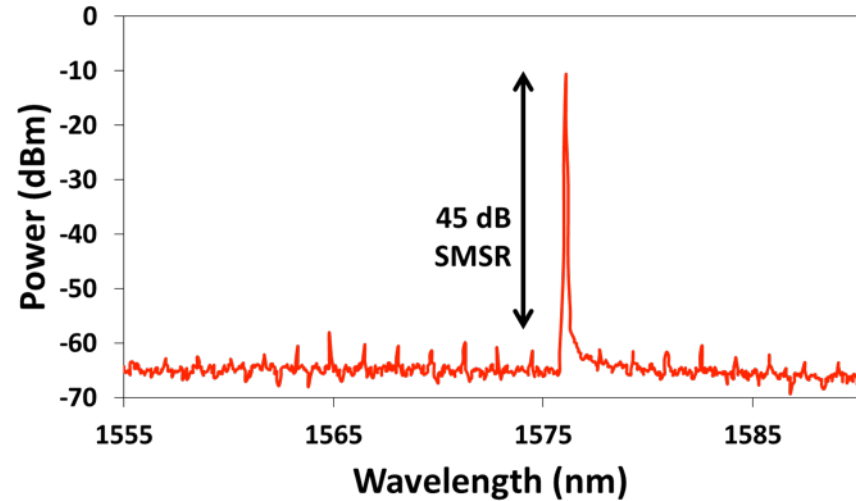
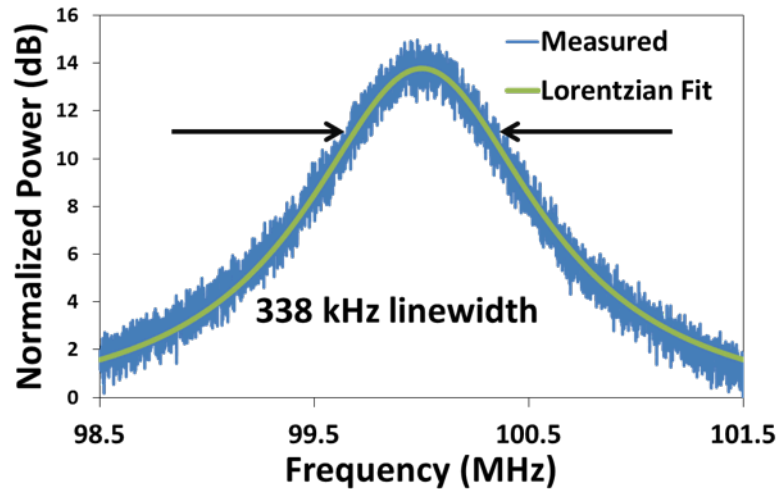
# Tunable Lasers

UCSB  
Ghent

# Widely Tunable Vernier Ring Laser



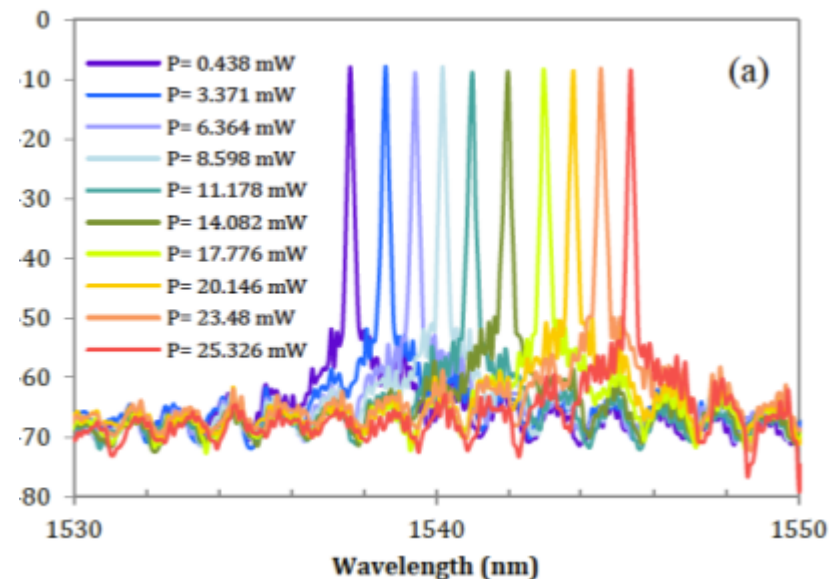
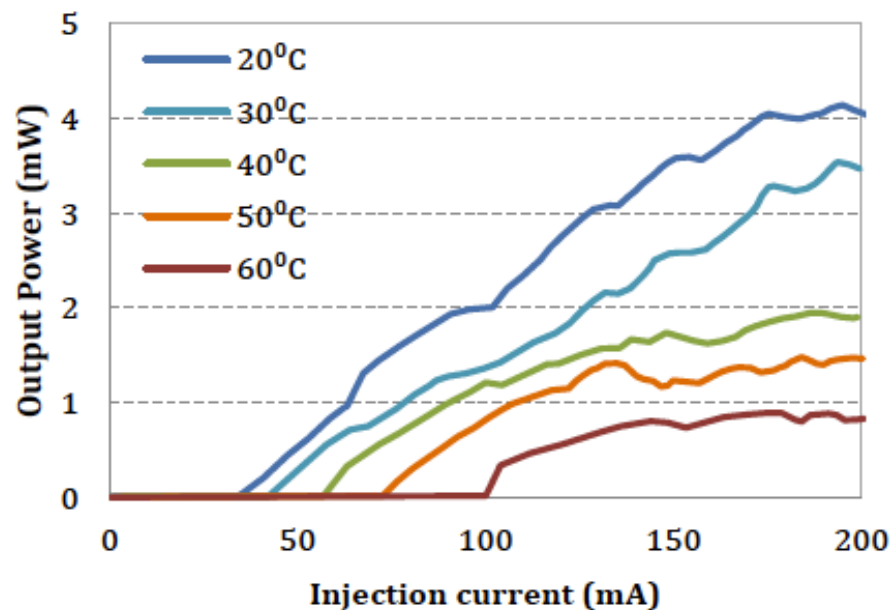
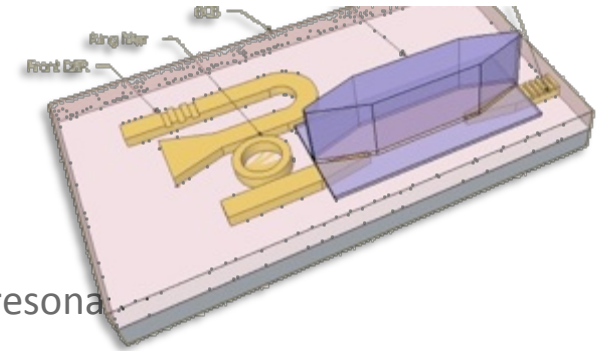
# Widely Tunable Vernier Ring Laser



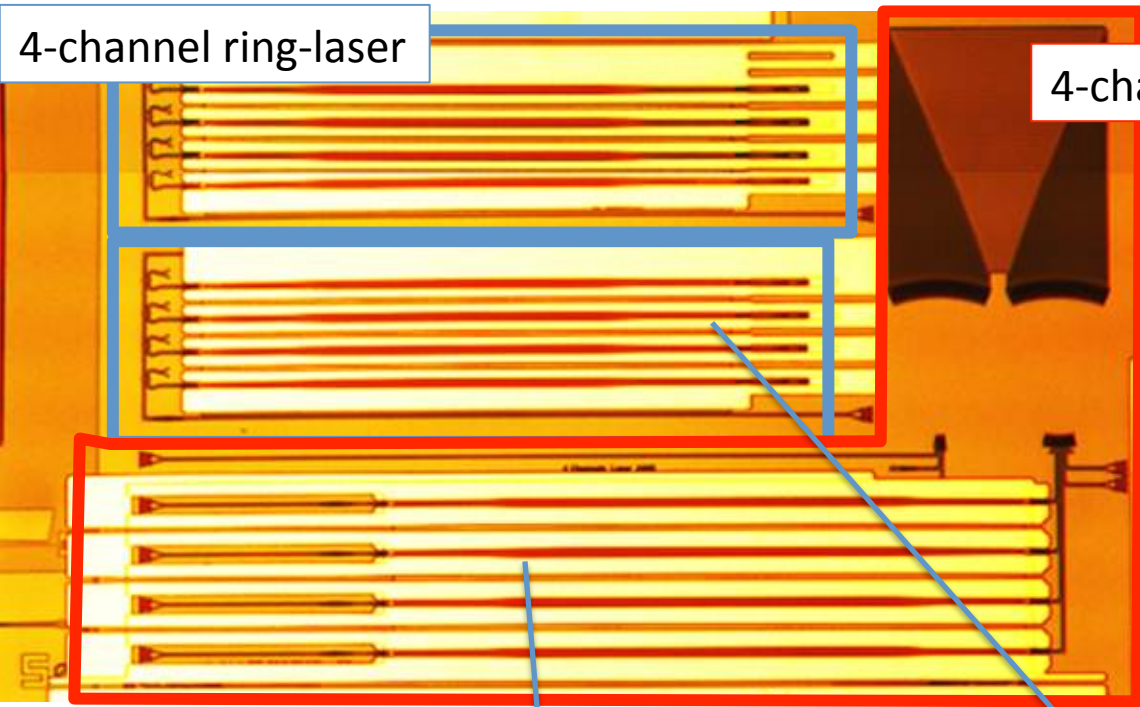
# III-V/Si extended cavity laser

## III-V/silicon tunable laser

- 8nm tuning range, based on thermo-optic tuning of silicon ring resonator
- > 40dB SMSR
- threshold of 35mA
- 4mW optical output power
- co-integrated with 10G silicon electro-optic modulator
- Realized in EU-project HELIOS (jointly with CEA-LETI, III-V labs)



Keyvaninia, Opt Express 2012



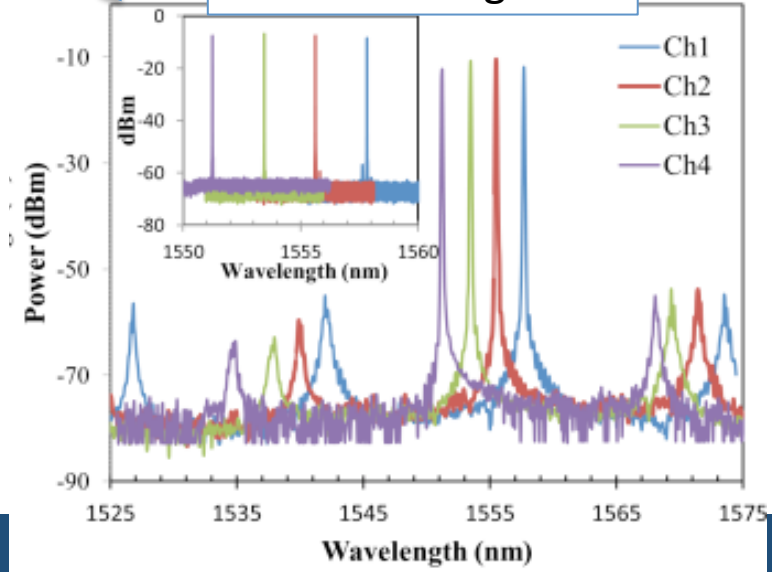
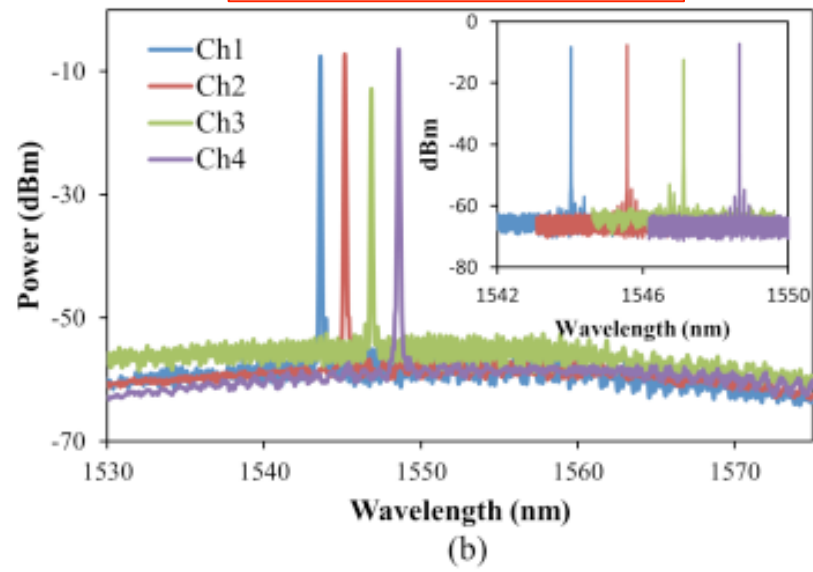
4-channel ring-laser

4-channel AWG-laser

Keyvaninia, Opt Express 2013

4-channel AWG-laser

4-channel ring-laser





# Integration

2D Scanners

Triplexers

Buffer Memories

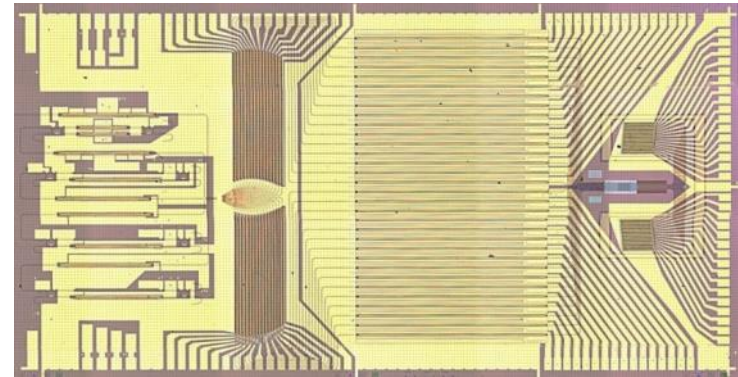
Mode Locked Lasers

# Fully Integrated hybrid silicon free-space beam steering source using a tunable laser phased array

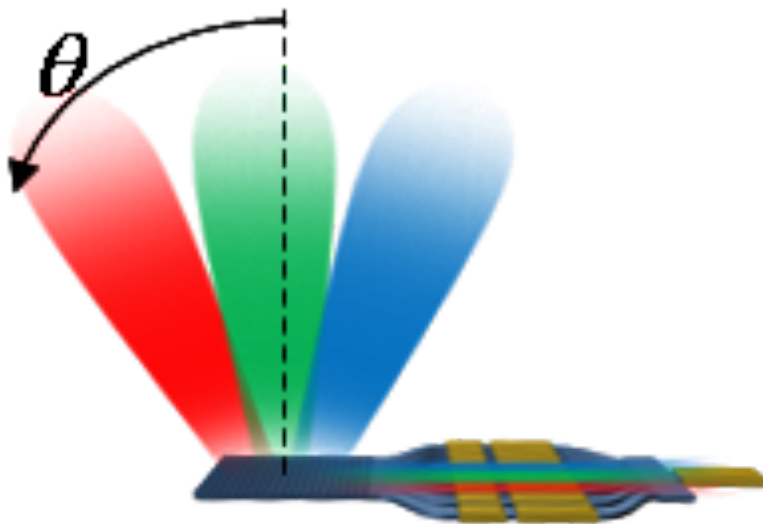
2D Scanning with

- Tunable laser and grating for  $\theta$
- Phased array emitter for  $\psi$

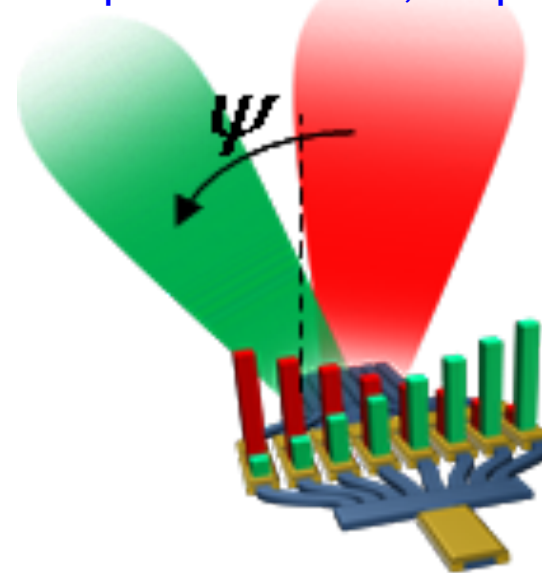
Scaling:  $N+1$ , not  $N^2$ !



4 tunable lasers, 32 amplifiers, 32 phase shifters, 32 photodetectors



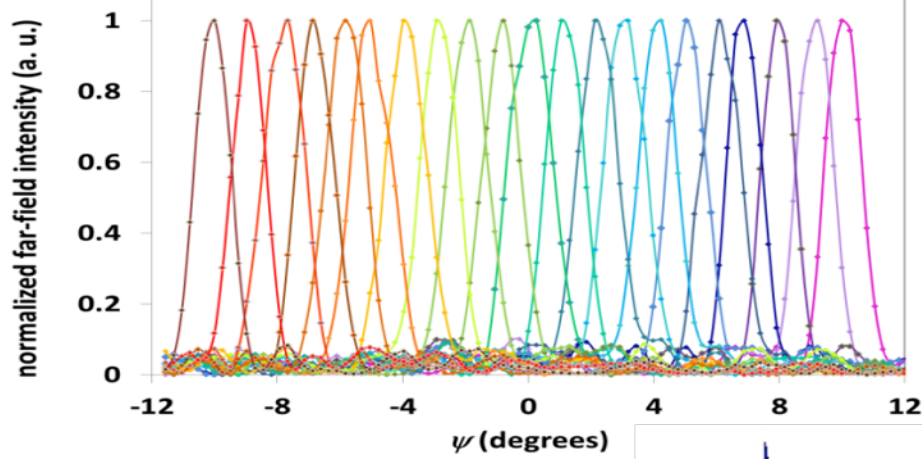
1 (wavelength)



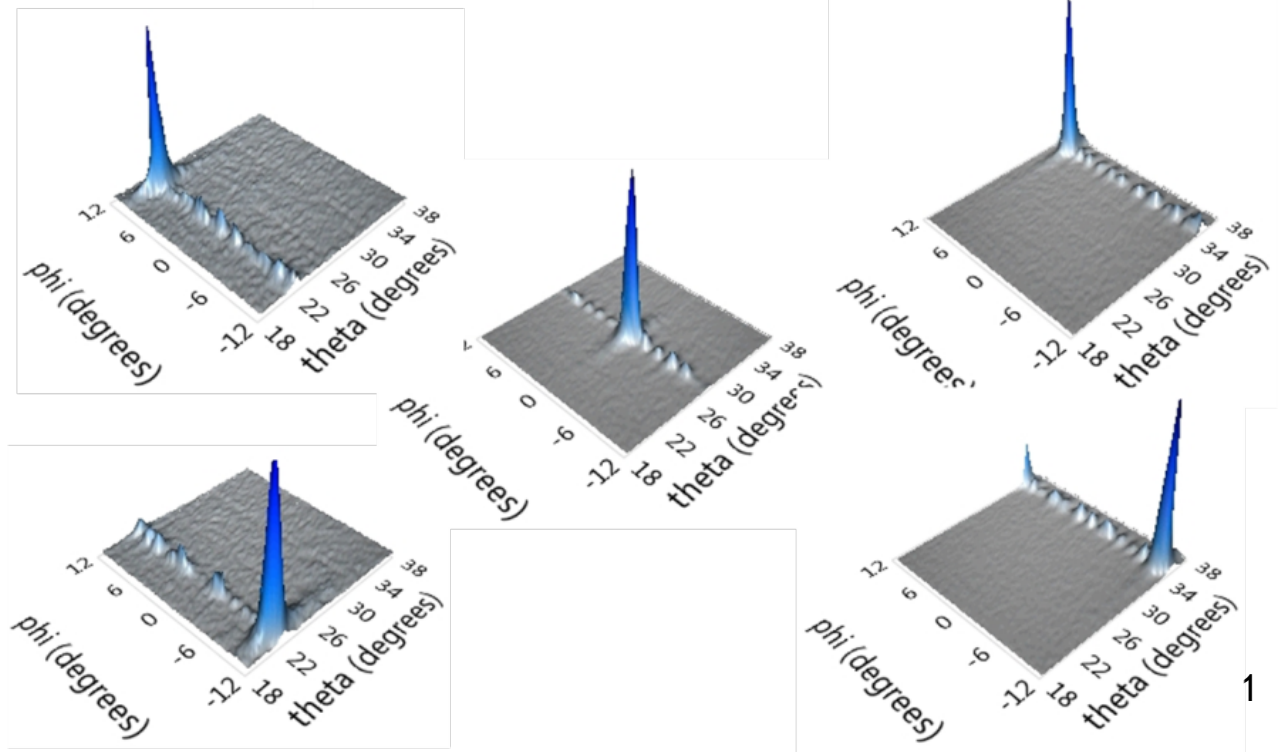
N (number of emitters)

# 2D Beam Scanning

1° angular tuning resolution, 1.6° FWHM beam width

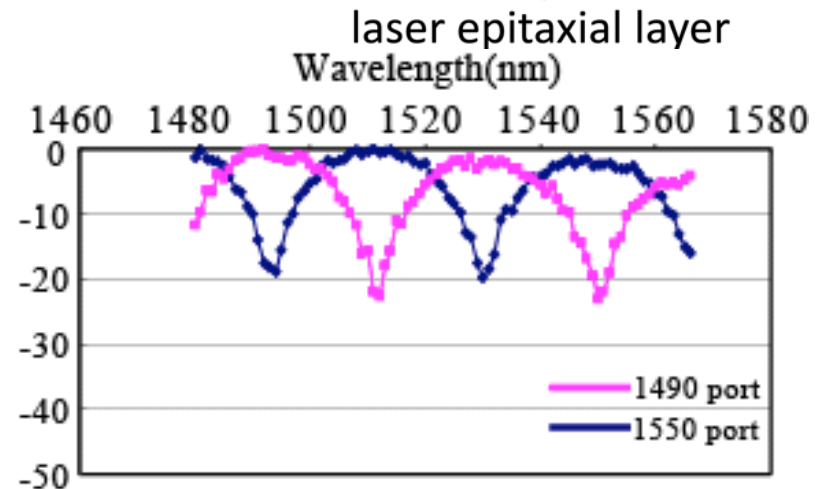
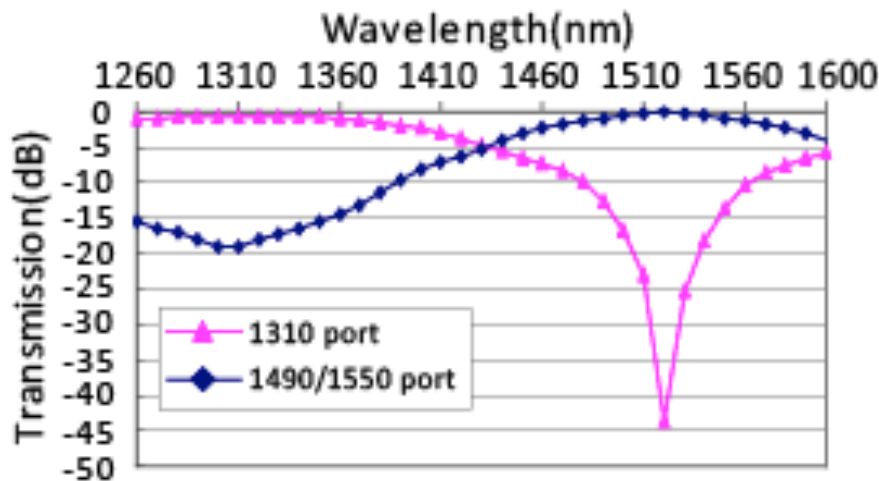
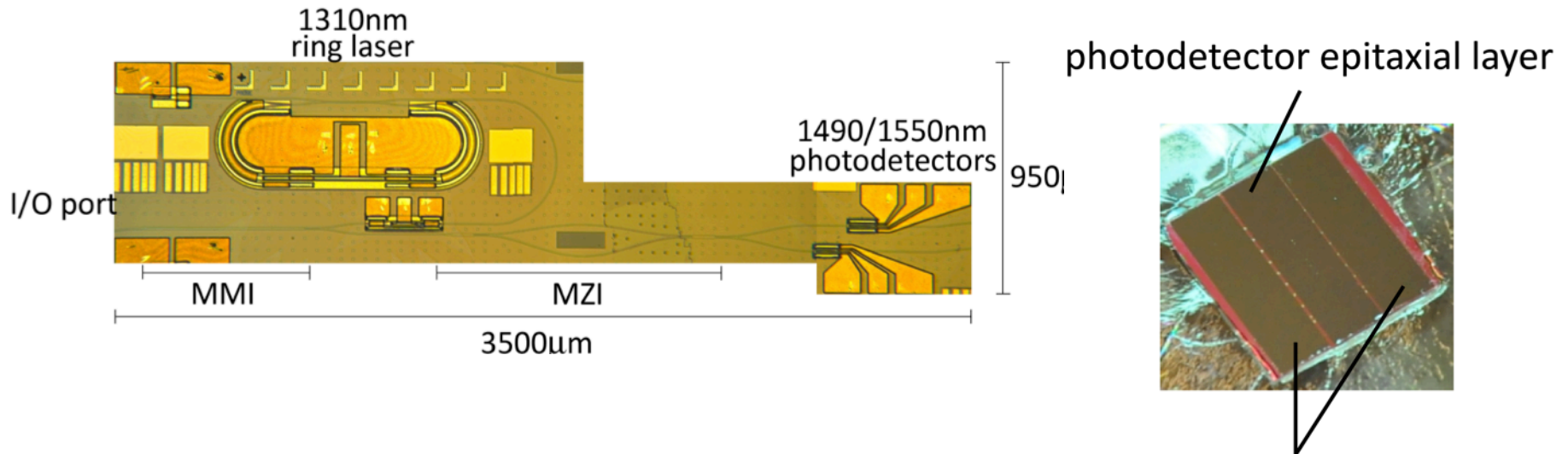


- Beam angle can be arbitrarily chosen within a 20° x 14° window

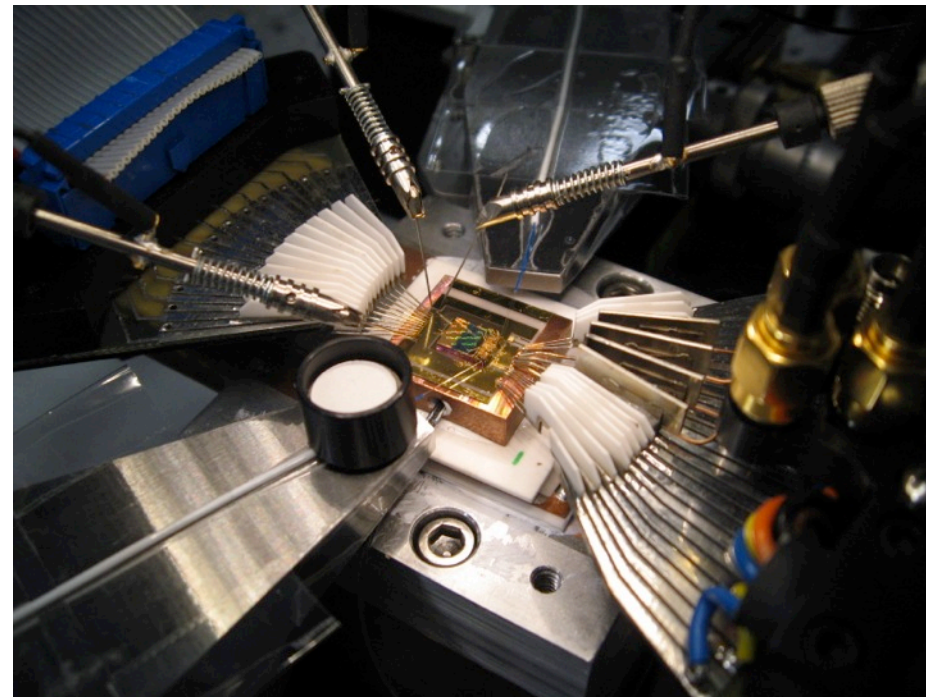
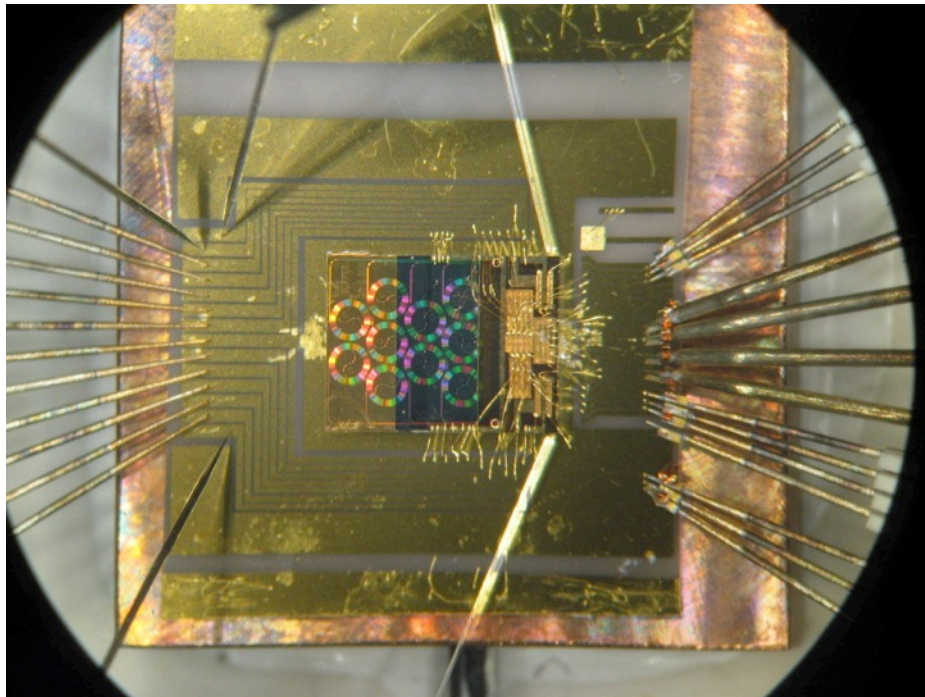
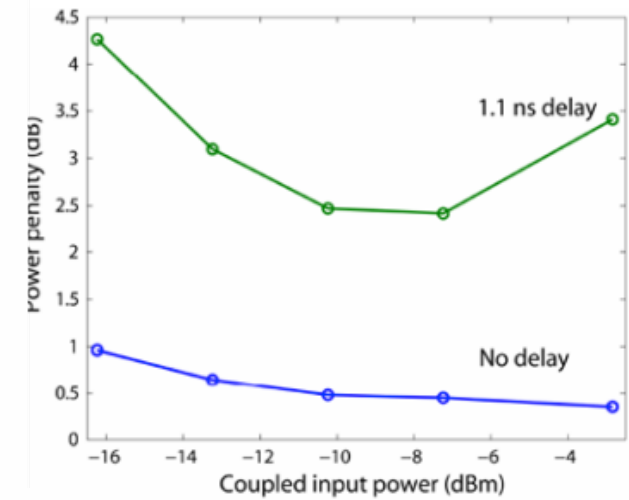
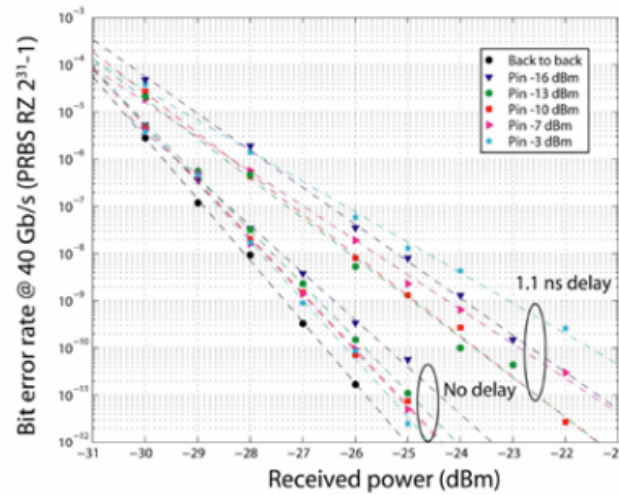
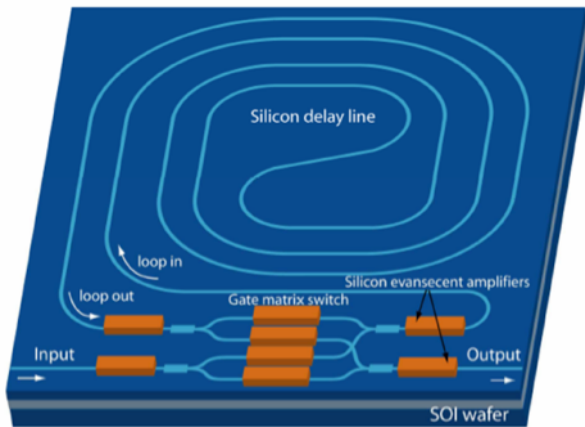


# Hybrid Silicon Triplexers

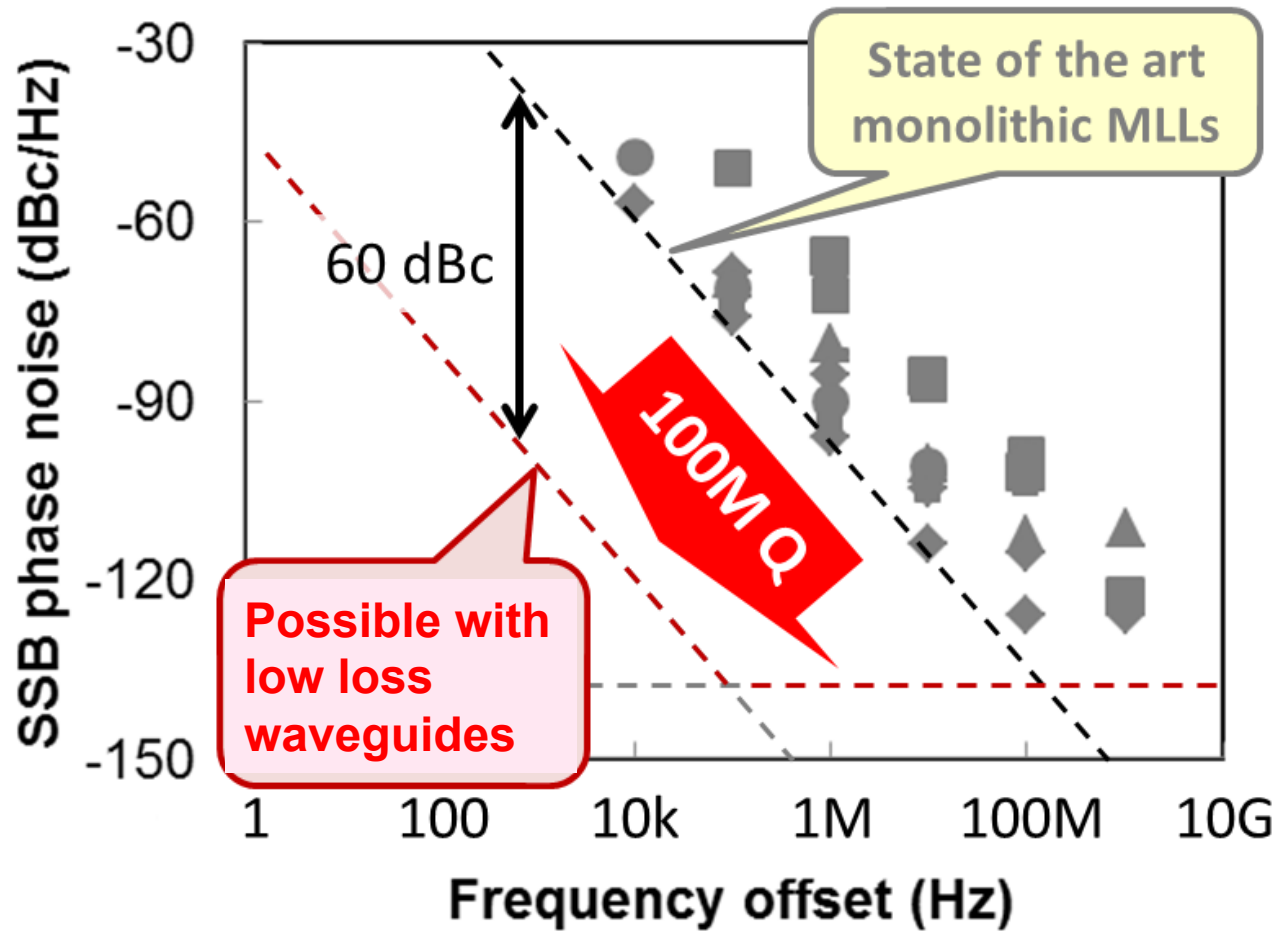
Laser, 1310/1500 nm MUX MMI, MZI 1550/1490 MUX, PDs integrated



# Optical Buffer Memory

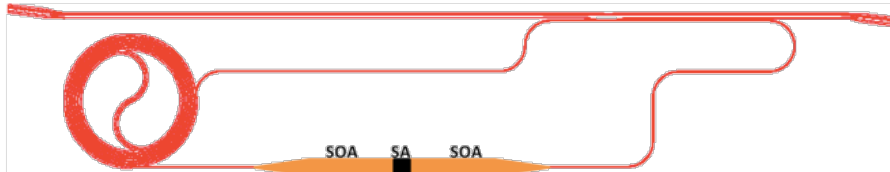


# Lower Loss Waveguides for Low Jitter Mode Locked Lasers

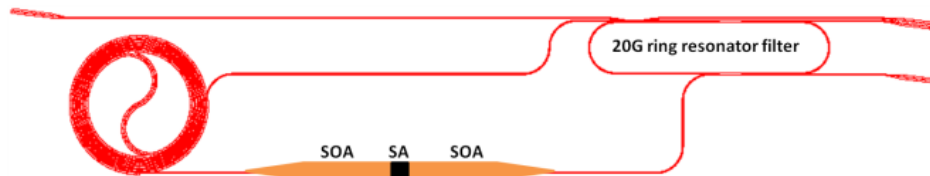
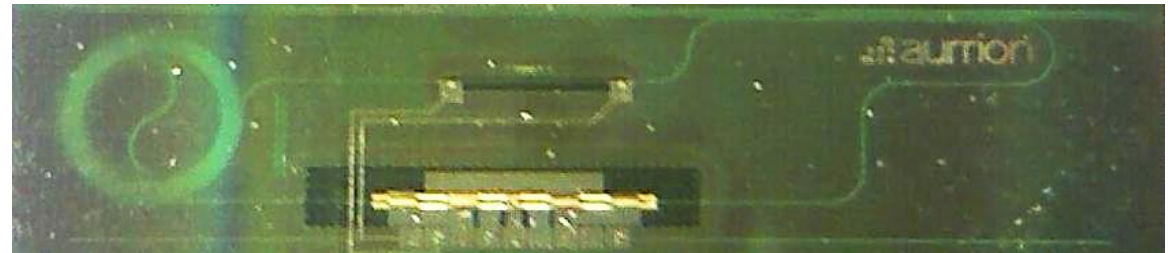


# Mode Locked Laser Stabilization by Harmonic ML and Integration of Long Cavities

- Longer cavities for low phase noise
- Harmonic mode locking for high frequencies
- Multiple pulses in the cavity are not well coupled
- Intracavity etalon to stabilize



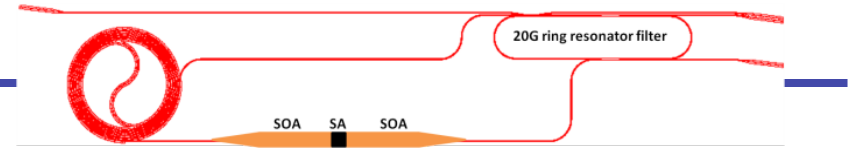
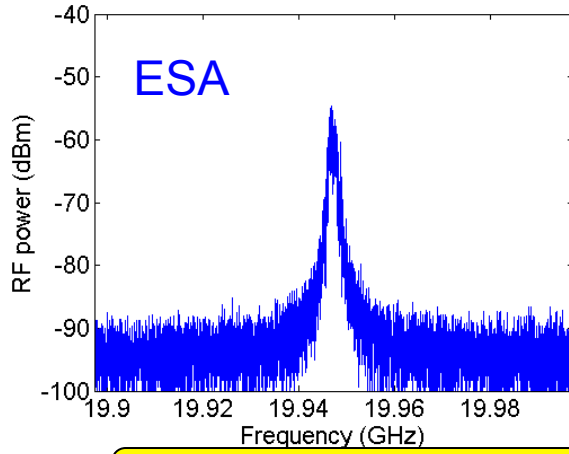
4cm cavity length



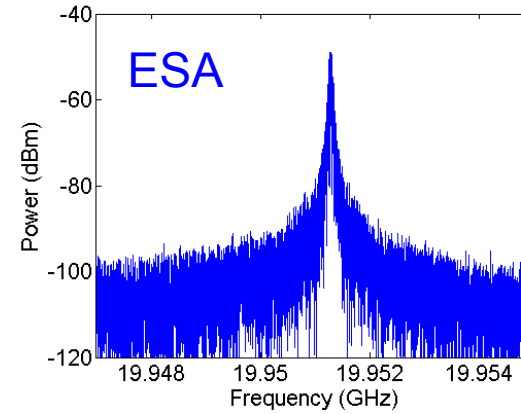
[Sudha Srinivasan: Th3A.4. 2:00-2:15 PM](#) –  
 “Suppression of supermode noise in a harmonically mode-locked hybrid silicon laser using an intra-cavity filter.”

# Passive Locking – comparison

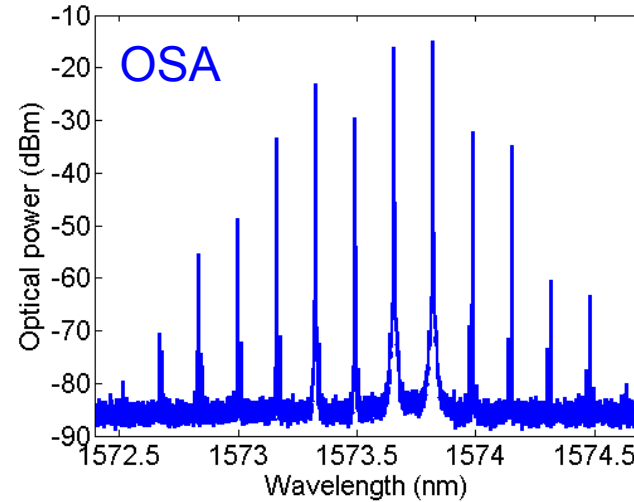
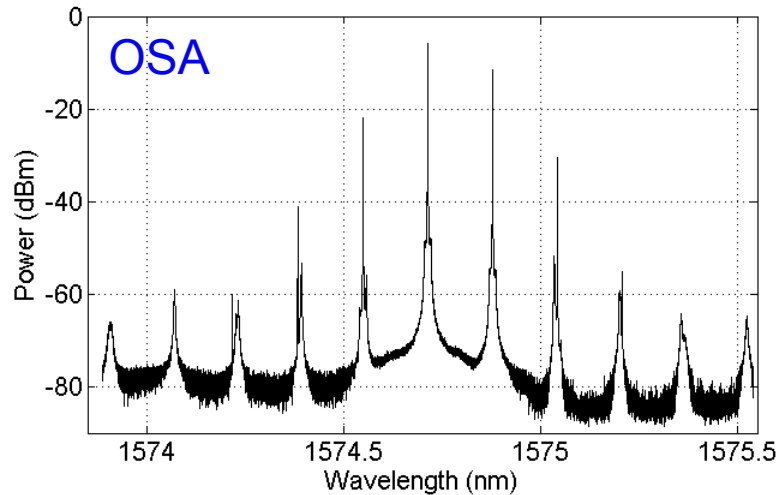
20G cavity –  
188mA, 0 V



2G cavity with filter  
-220mA, -0.5V



Linewidth improvement – 1.5MHz → 52kHz (30x)



SOA lengths 900mm and 1.4mm respectively.  
Absorber length 50mm in both cases

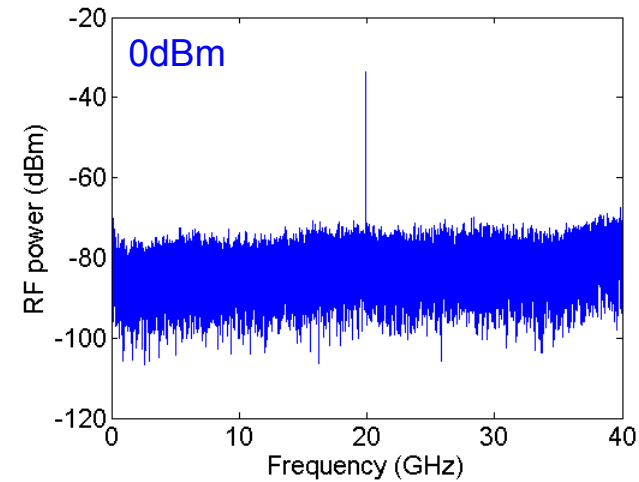
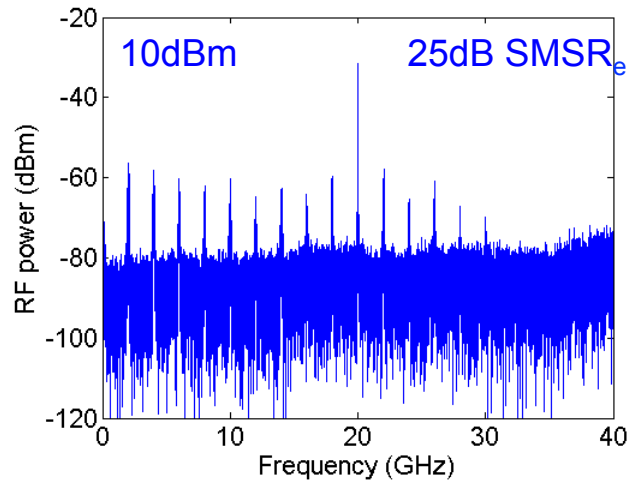


# Hybrid locking – comparison

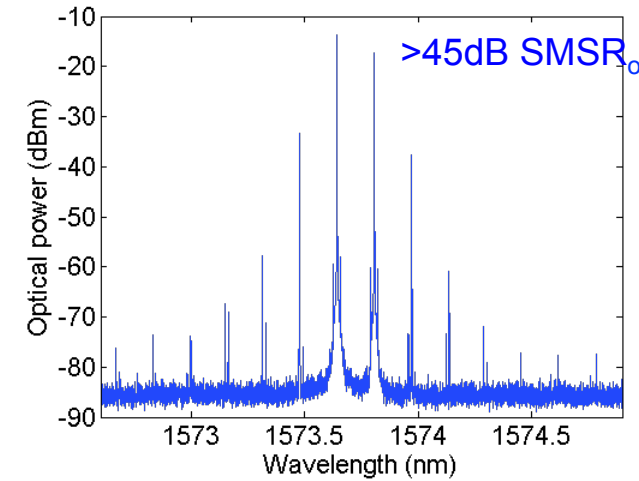
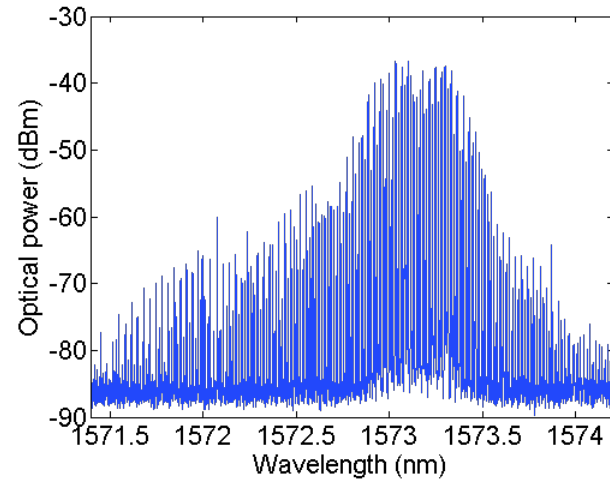
Without Filter

With Filter

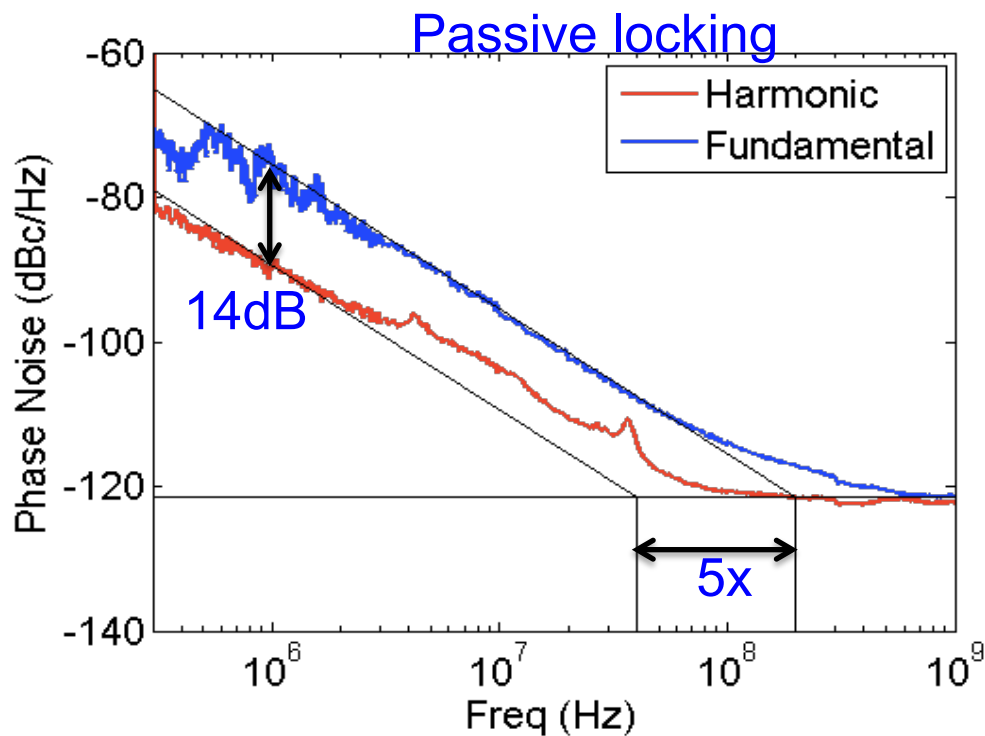
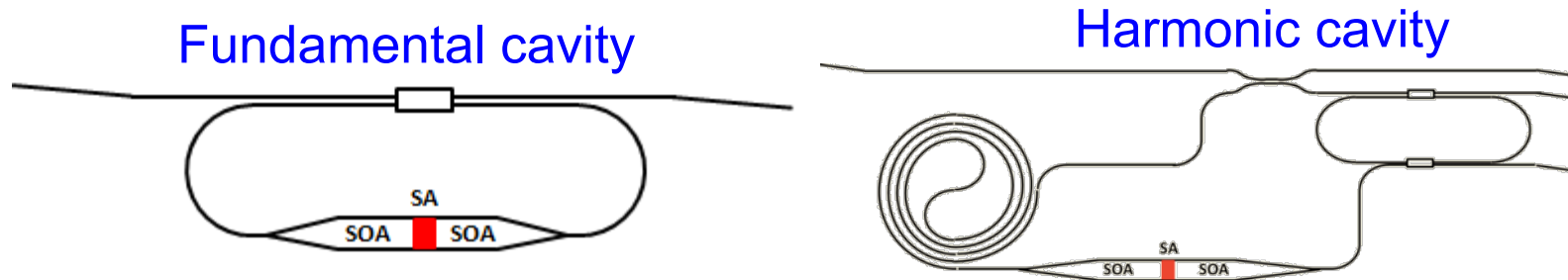
Electrical spectrum



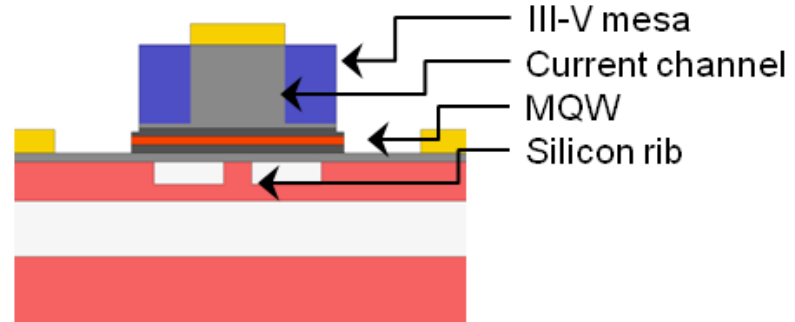
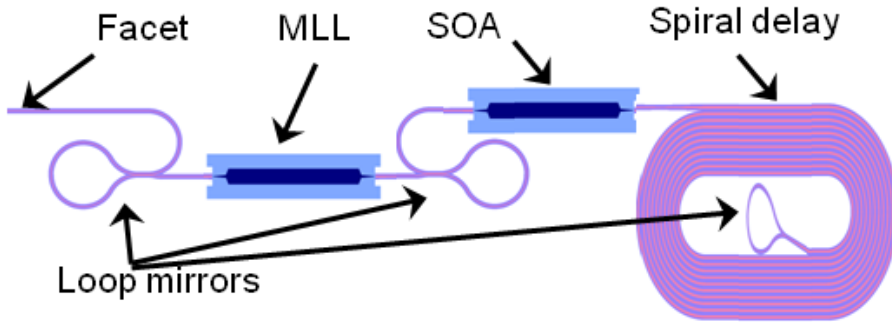
Optical spectrum



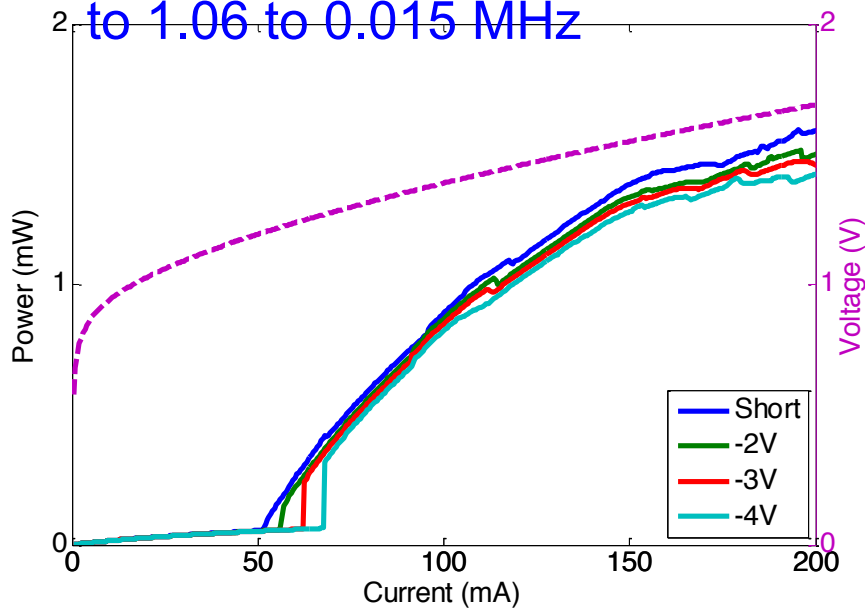
# Advantage of Long Laser Cavity



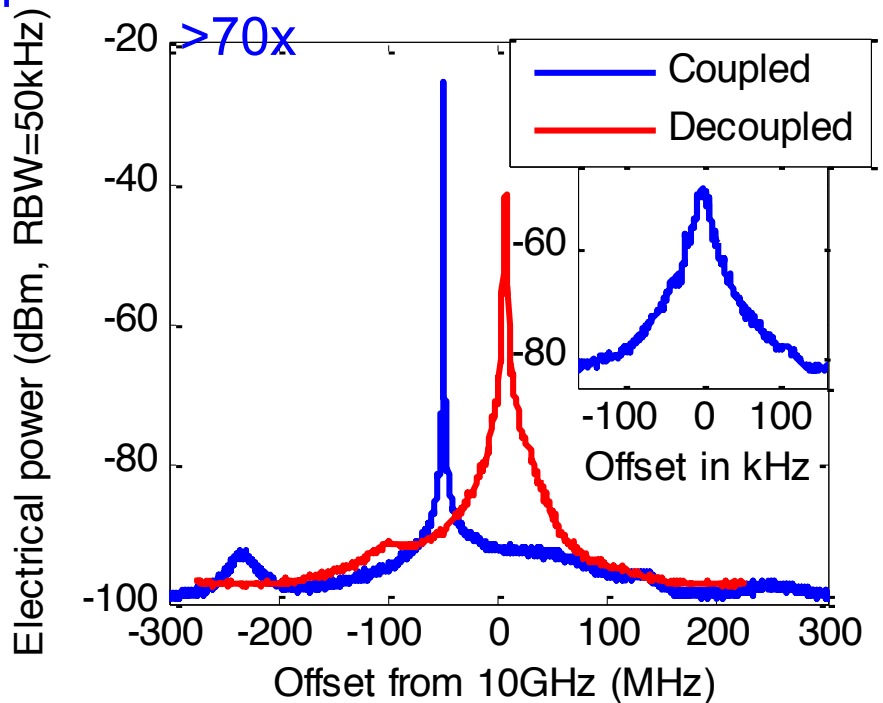
# Integrated Feedback Stabilized Mode-Locked Laser



- Passive mode locking at 10 GHz
- Microwave linewidth reduction from to 1.06 to 0.015 MHz



## RF Linewidth reduction

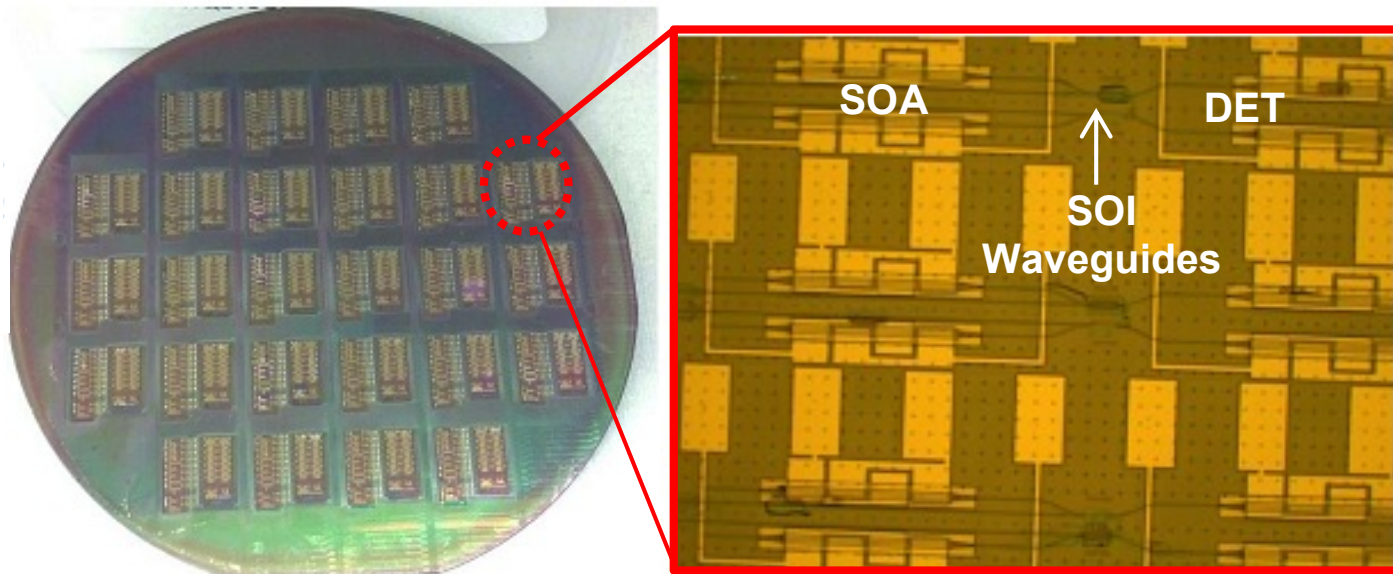
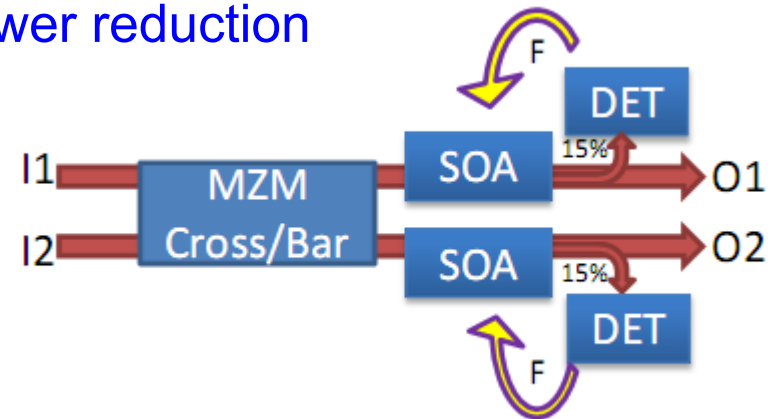


# Integration with Electronics

# CMOS Integration in Photonic IC

Chen et al. OFC and Communications Magazine (2013)

- ❑ “Smart Photonics” – Integrated electronic w/ photonic ICs
- ❑ Avoid driving 50Ω terminations **Power reduction**
- ❑ Self-calibration
- ❑ Active feedback control

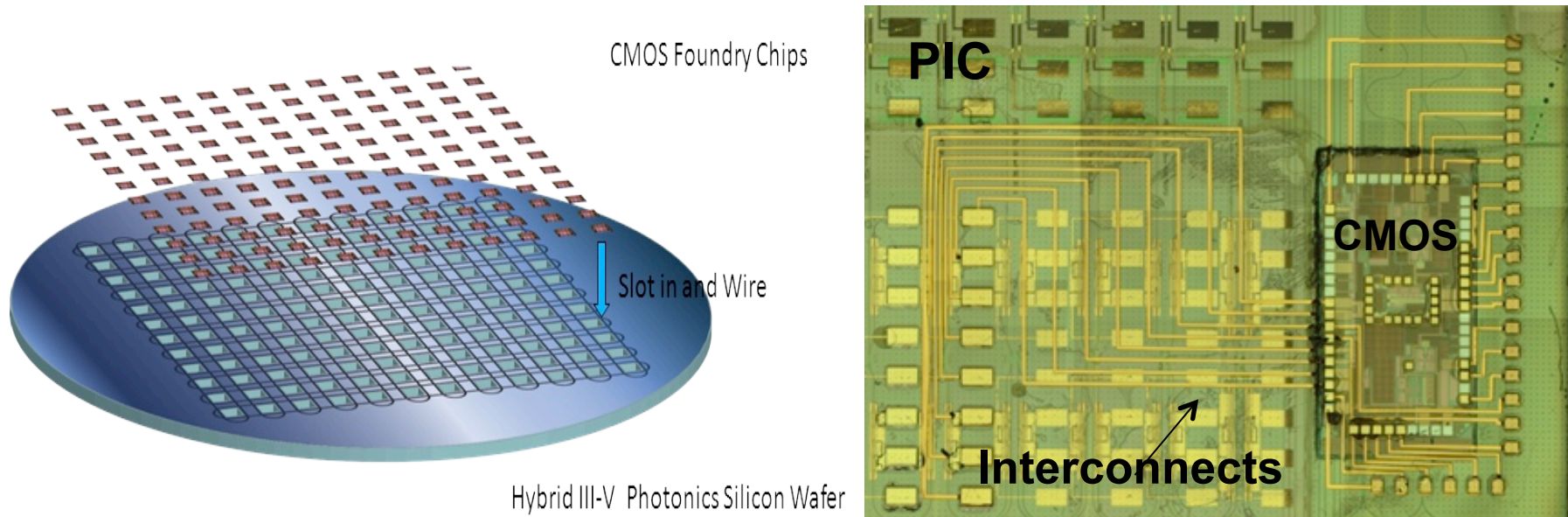


Hybrid Silicon PIC from Aurrion

# CMOS Integration in Photonic IC

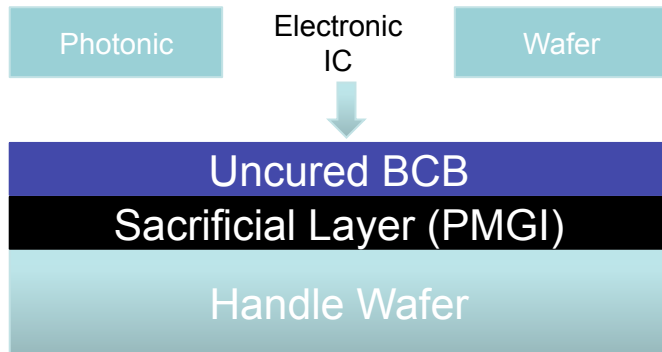
(with Theogarajan)

- ❑ “Smart Photonics” – Integrated electronic w/ photonic ICs
- ❑ Avoid driving 50Ω terminations
- ❑ Self-calibration
- ❑ Active feedback control

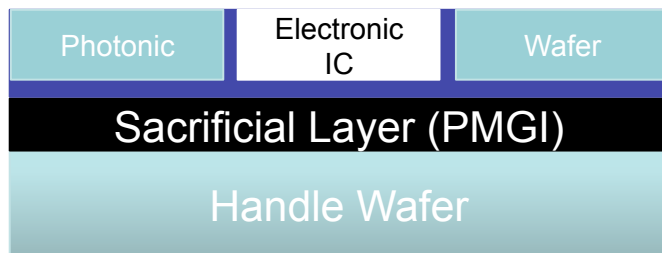


# Electronic-Photonic Integration

RDL First Process to ensure surface flatness



Place Etched Photonic Chip and Electronic IC



Release assembly from Sacrificial layer

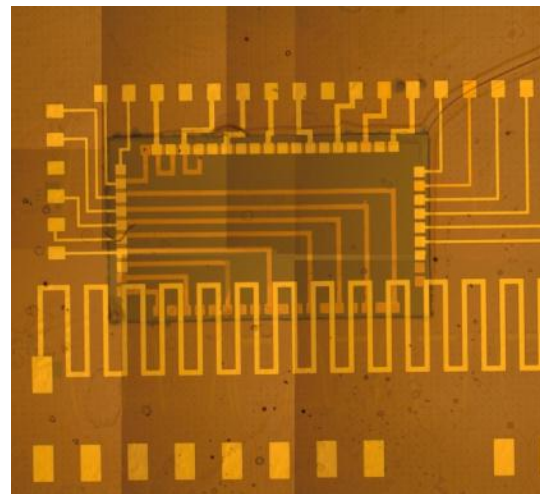


Etch electrical pad access and wire

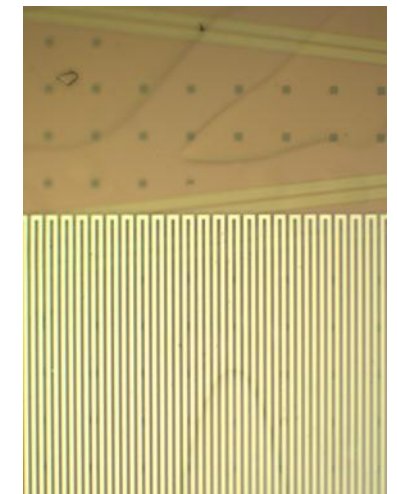


20μm pitch and density

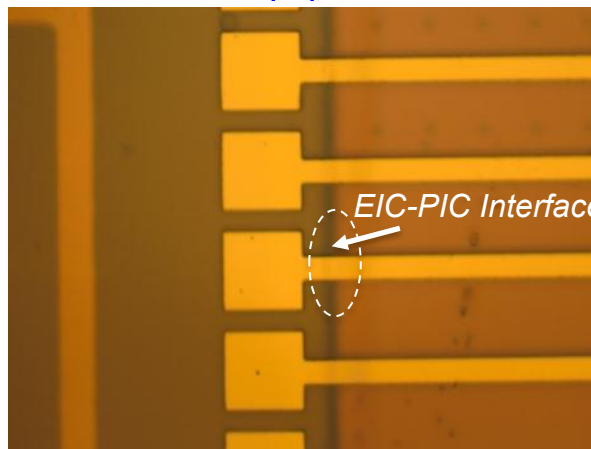
5μm pitch and density



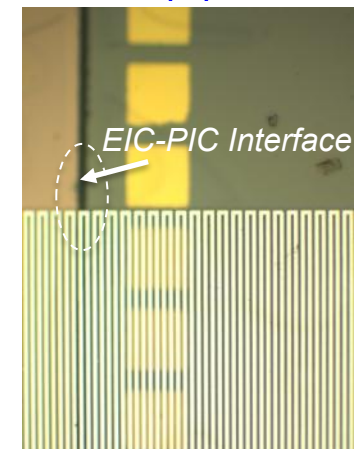
(a)



(c)



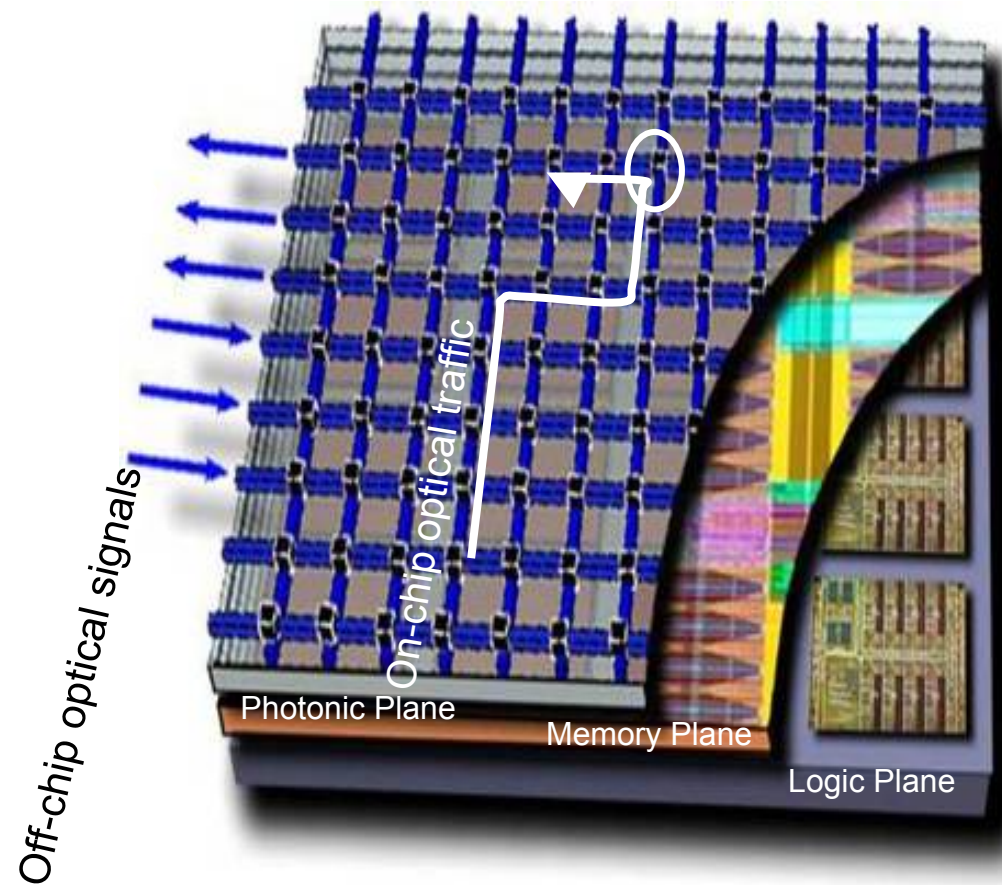
(d)



(d)

# Network on a Chip: Optical Interconnects

- 3D layer stacking will be prevalent in the 22nm timeframe
- Intra-chip optics can take advantage of this technology
- Photonics layer (with supporting electrical circuits) more easily integrated with high performance logic and memory layers
- Layers can be separately optimized for performance and yield





# Commercialization

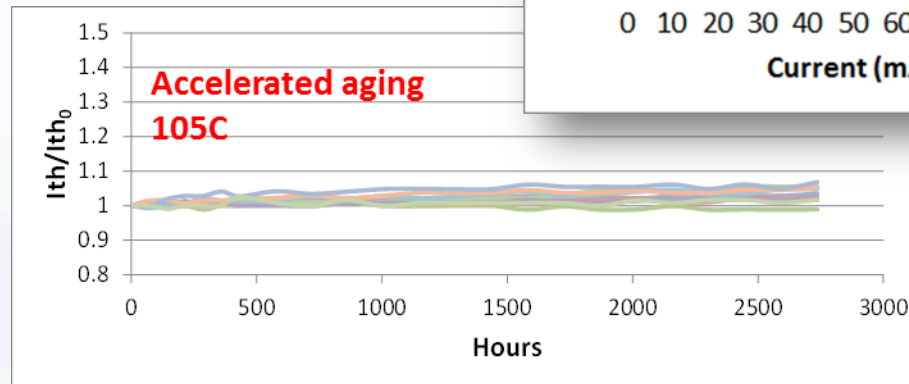
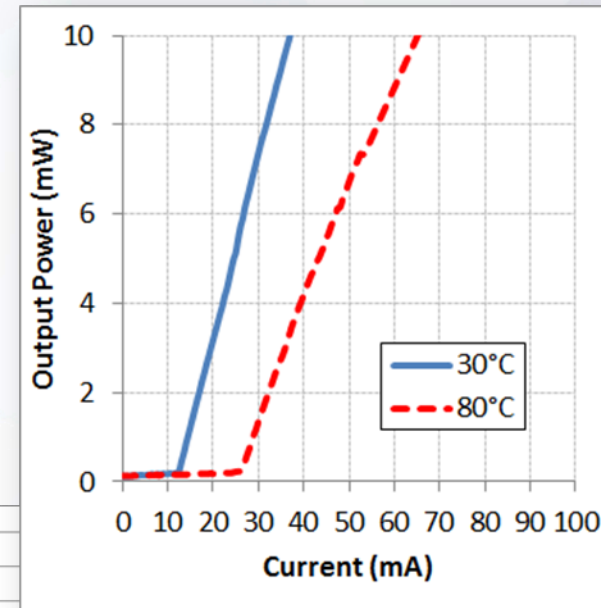
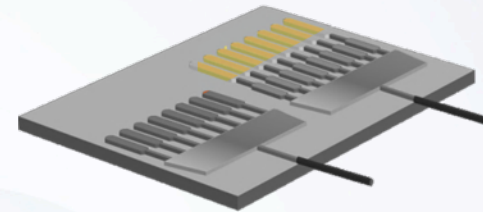
Aurrion

Intel

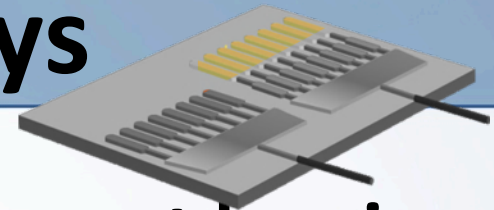
Hewlett Packard

# Integrated Lasers

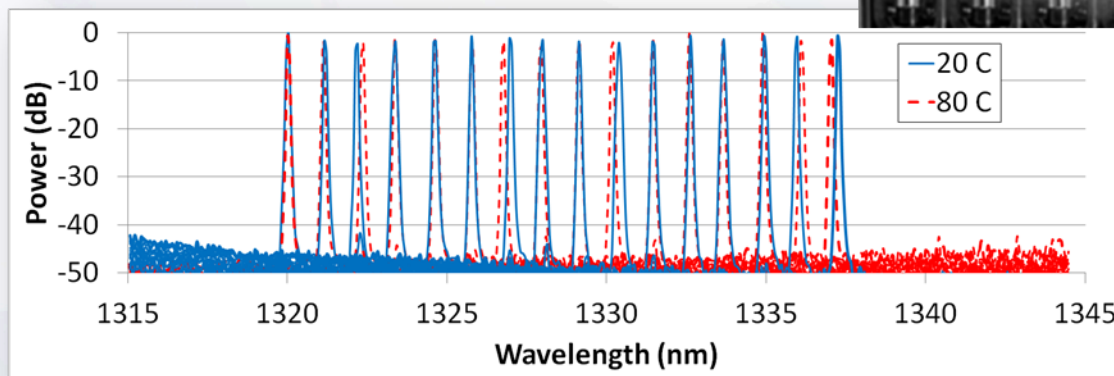
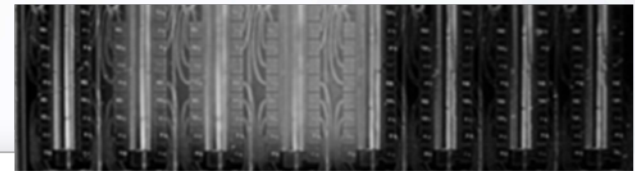
- III-V gain integrated on silicon waveguides
- High power/High efficiency
  - >25% at 30C
  - 15% at 80C
  - >20mW



# WDM Laser Arrays

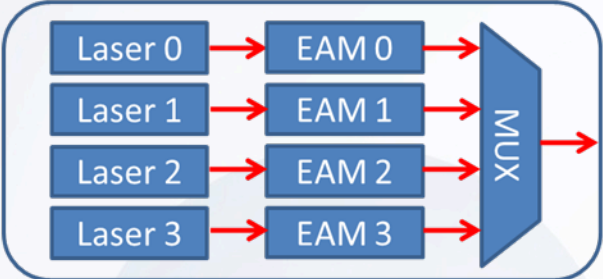


- **High yield integrated laser breaks cost barrier**
  - Large WDM arrays processed in parallel
- **Uncooled operation**
  - Wavelength-locking across temperature (20-80C) without a TEC
  - 200GHz (or 800GHz) grid

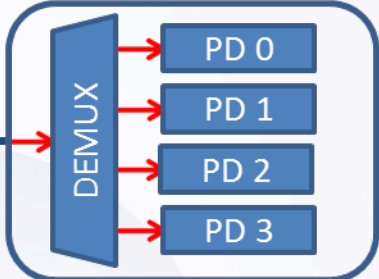


# 100G PIC Links

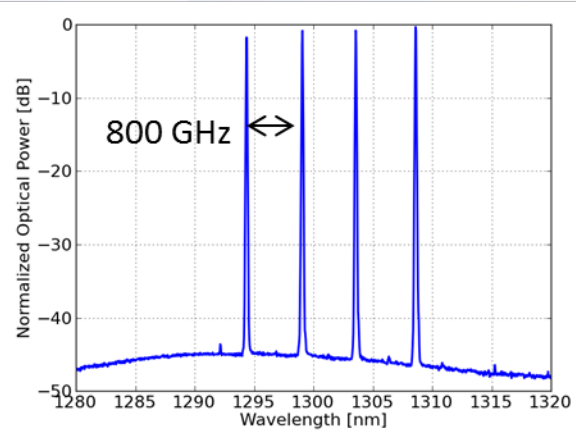
100G WDM Tx PIC



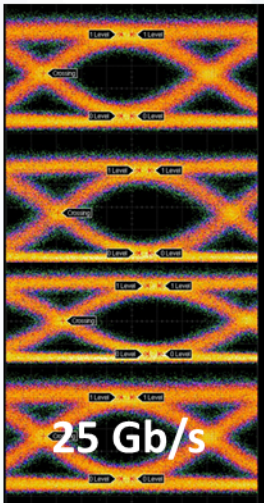
100G WDM Rx PIC



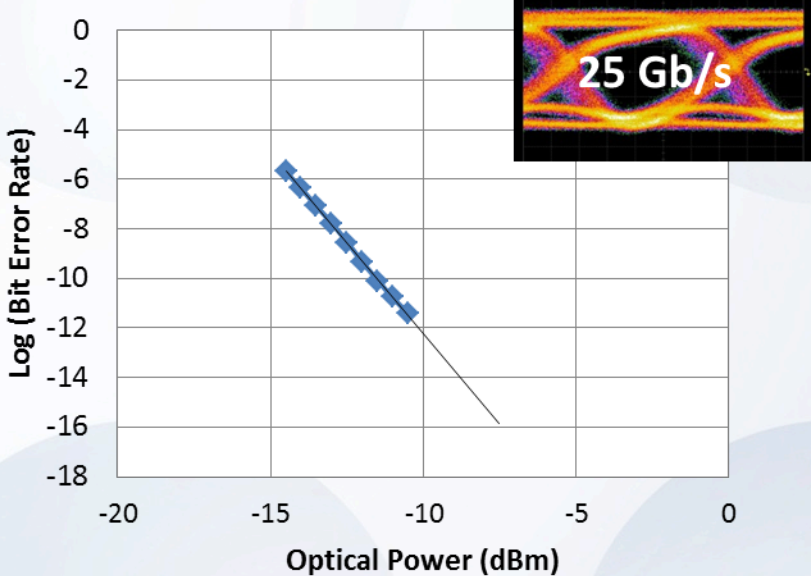
Laser Spectrum



Tx Eye Diagrams

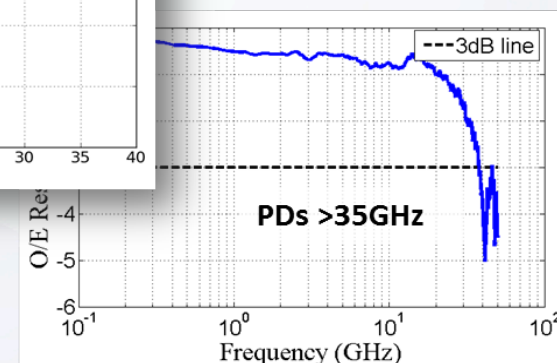
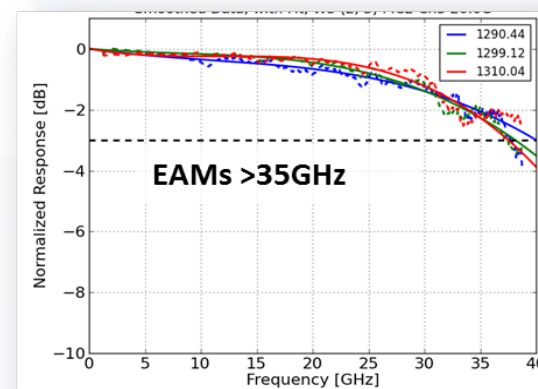
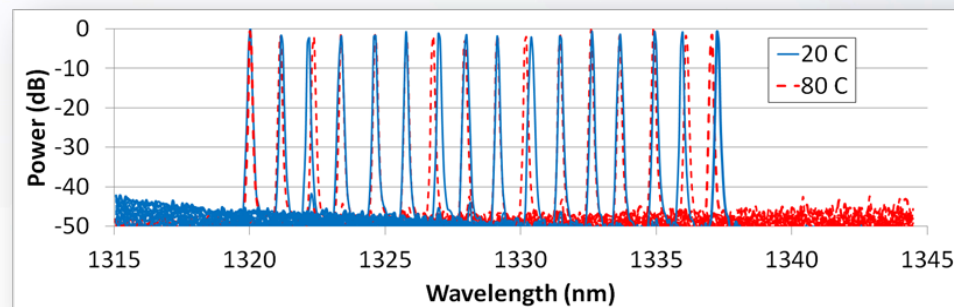


Rx Eye Diagram



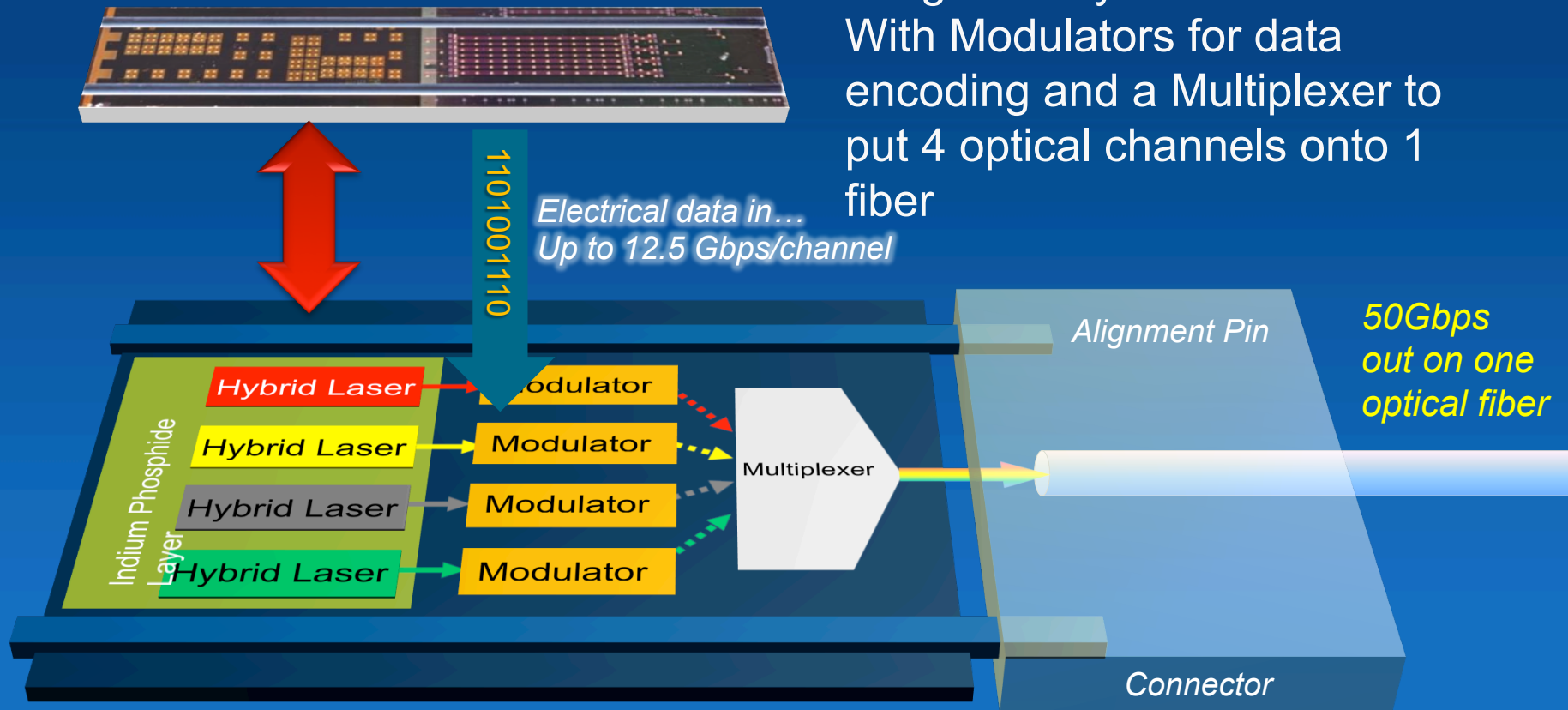
# Scaling to 400G+

- **Uncooled 16x laser arrays on silicon demonstrated**
  - Locked to 200GHz grid from 20-80C = no TEC required
- **3dB bandwidth of EAMs & PDs >37 GHz**
  - Supports 50Gb/s



# Integrated Transmitter Chip

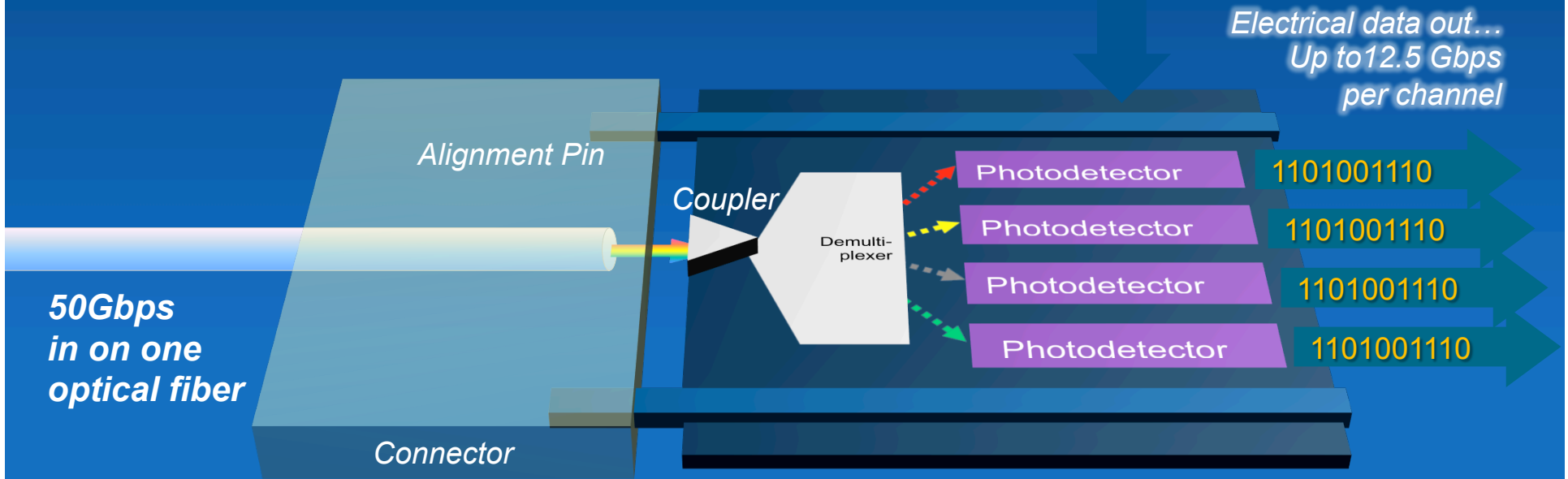
Integrates Hybrid Silicon Lasers With Modulators for data encoding and a Multiplexer to put 4 optical channels onto 1 fiber



**Parallel channels are key to scaling bandwidths at low costs**

# Integrated Receiver Chip

Integrates a coupler to receive incoming light with a demultiplexer to split optical signals and Ge-on-Si photodetectors to convert photons to electrons



**Receives 4 optical channels at 12.5Gbps and converts to electrical data**

# Jan 2013 OCP – Facebook announcement

Frank Frankowsky  
FB VP R&D



Justin Rattner  
Intel CTO

Andy Bechtolsheim  
Arista: Founder and CEO  
Sun: Founder and CTO

## Announced at Facebook's Open Compute Summit

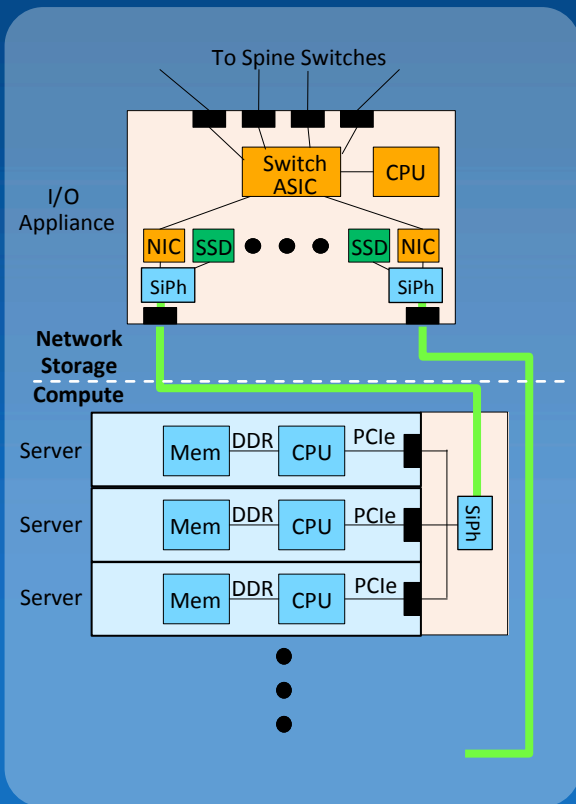
1. Intel is working with Facebook and Quanta to define a new class of server architectures
2. First architecture is disaggregation
3. Intel has sampled it's 100G photonic modules





# Photonics in the Rack

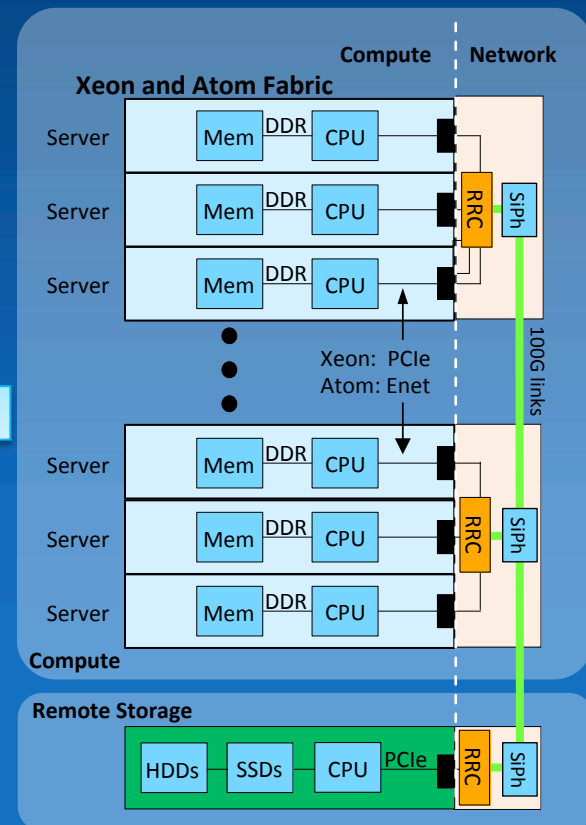
Network & Storage move into TOR Switch



Optical Rack



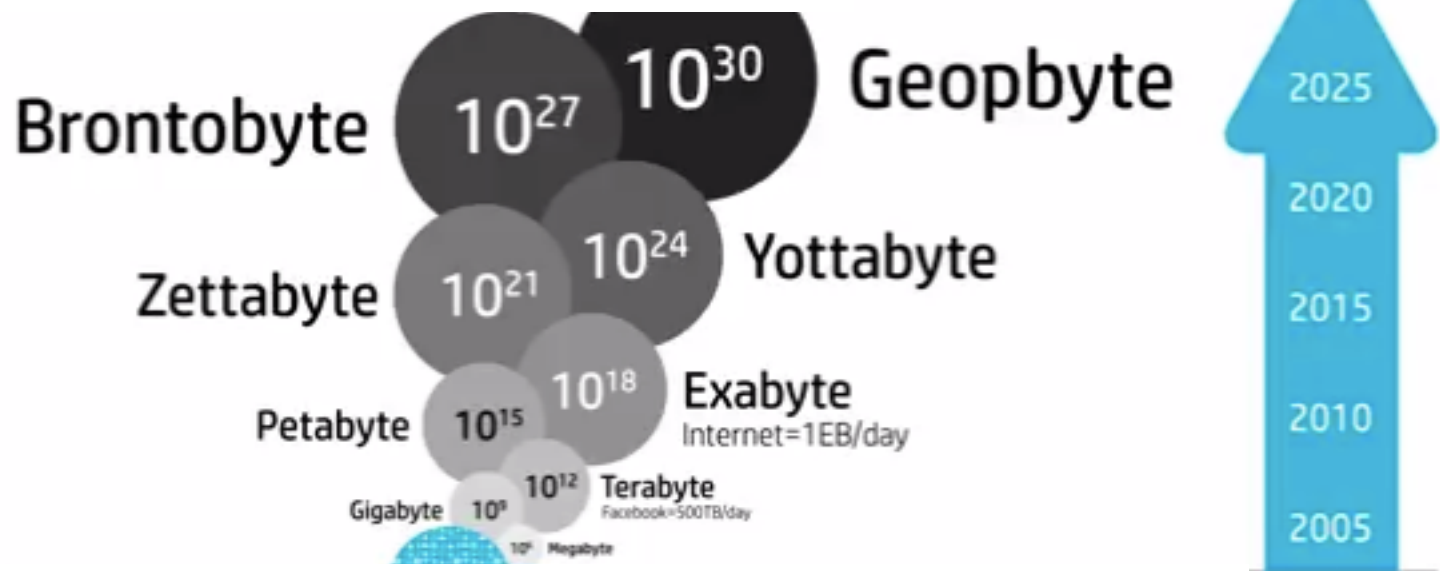
TOR Switch distributed into Servers



Architecture offers flexible solutions and multiple Value Propositions

# Hewlett Packard: “The Machine”

The Machine started to take shape two years ago, after Fink was named director of HP Labs. Assessing the company’s projects, he says, made it clear that HP was developing the needed components to create a better computing system. Among its research projects: a new form of memory known as memristors; and silicon photonics, the transfer of data inside a computer using light instead of copper wires. And its researchers have worked on operating systems including Windows, Linux, HP-UX, Tru64, and NonStop.



HP’s proposed silicon photonics would also be a big deal. HP, Intel (INTC), and others have been struggling to shrink speedy fiber-optic equipment enough to replace cheap, proven copper wiring inside a computer. In theory, fiber could also replace Ethernet cables and link entire racks of servers together.

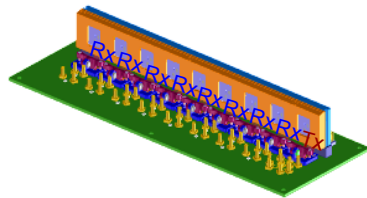
# Supercomputing: HP photonics technologies



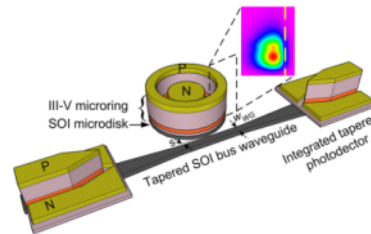
Active cable



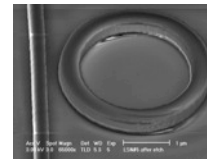
Optical bus



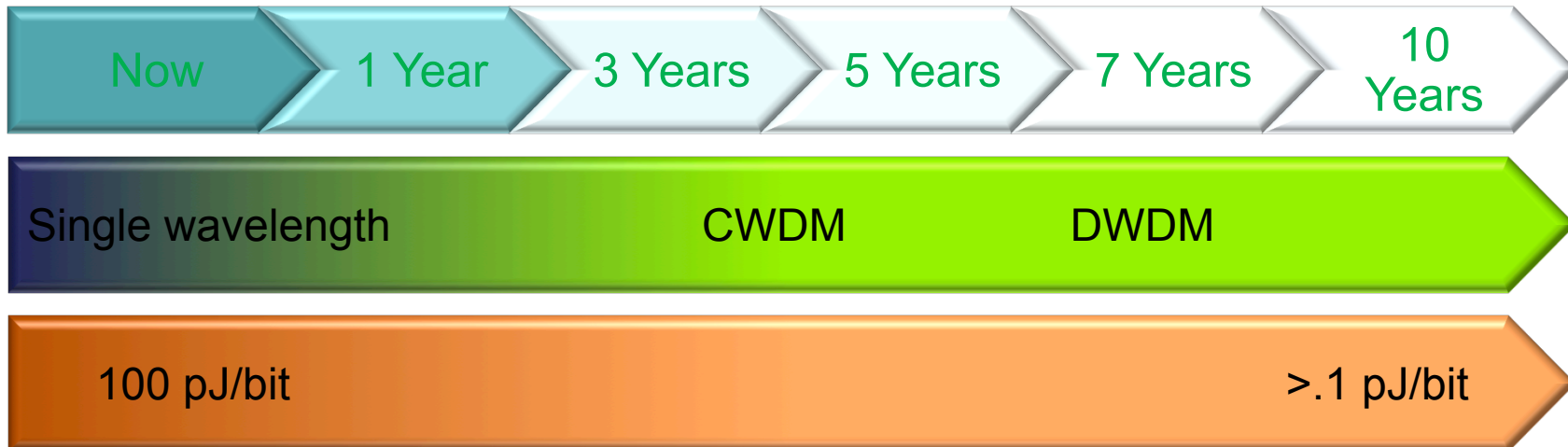
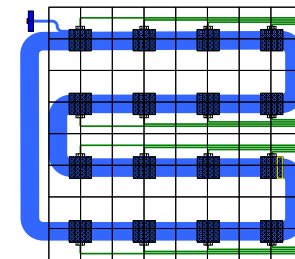
Hybrid microring laser



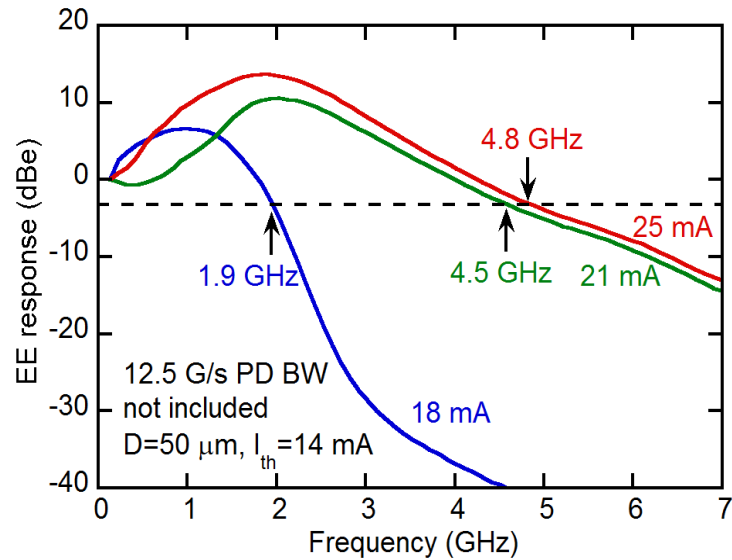
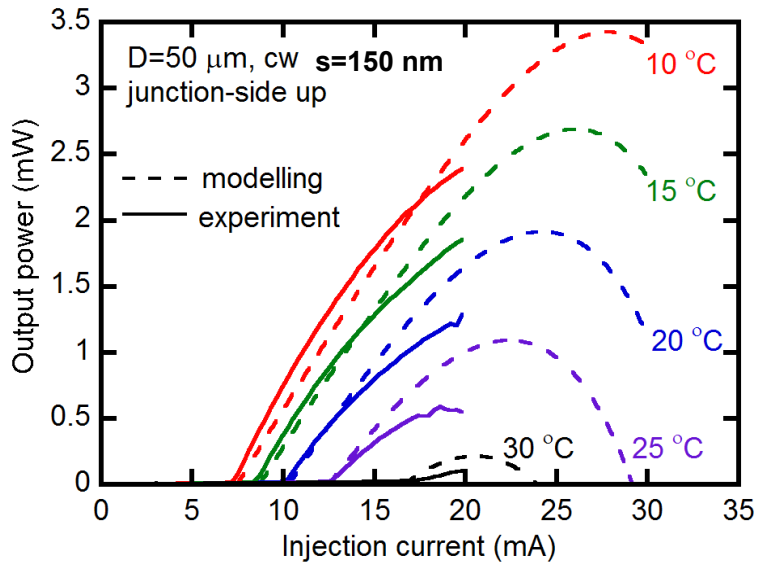
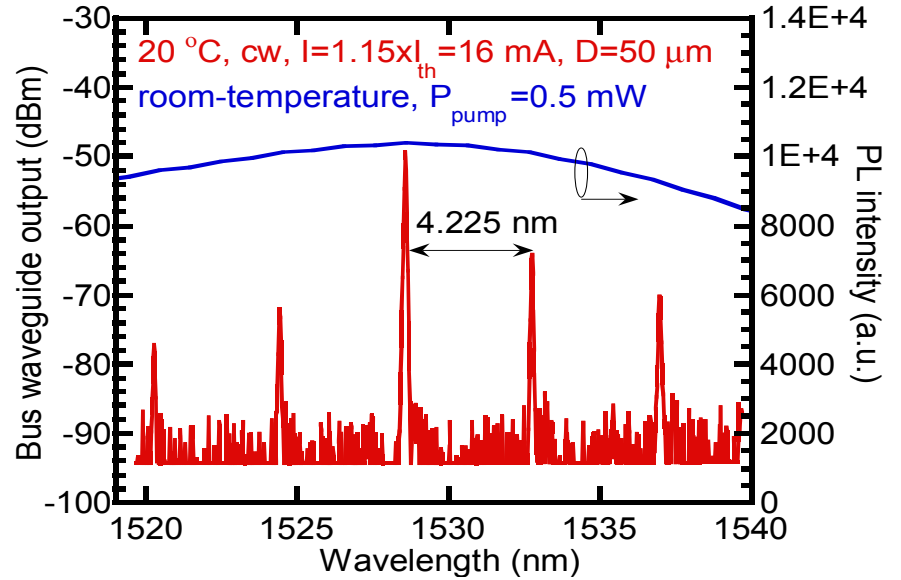
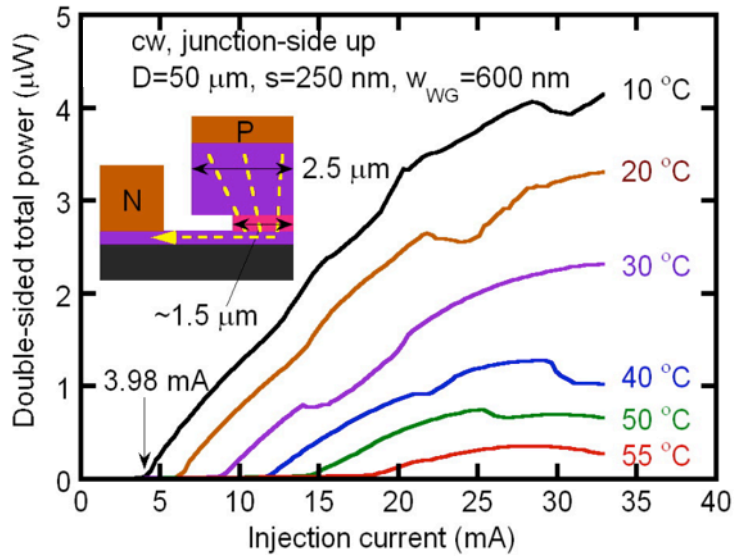
Silicon PIC



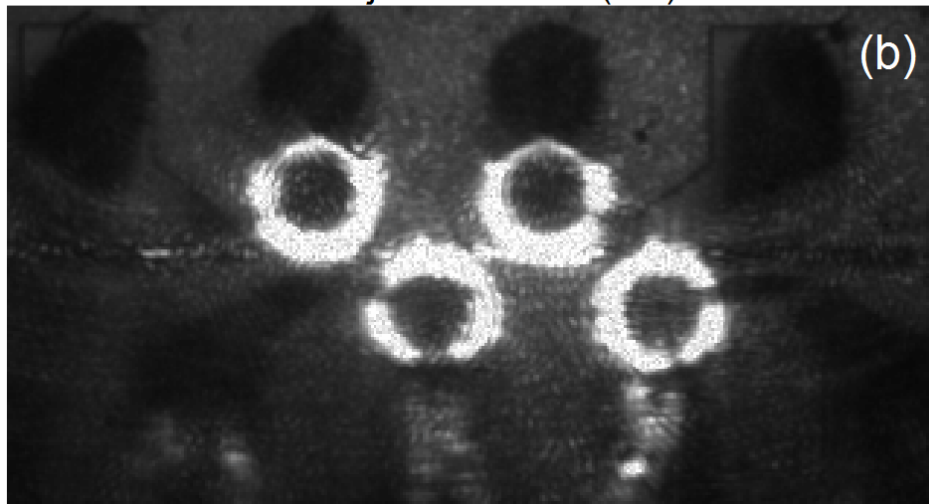
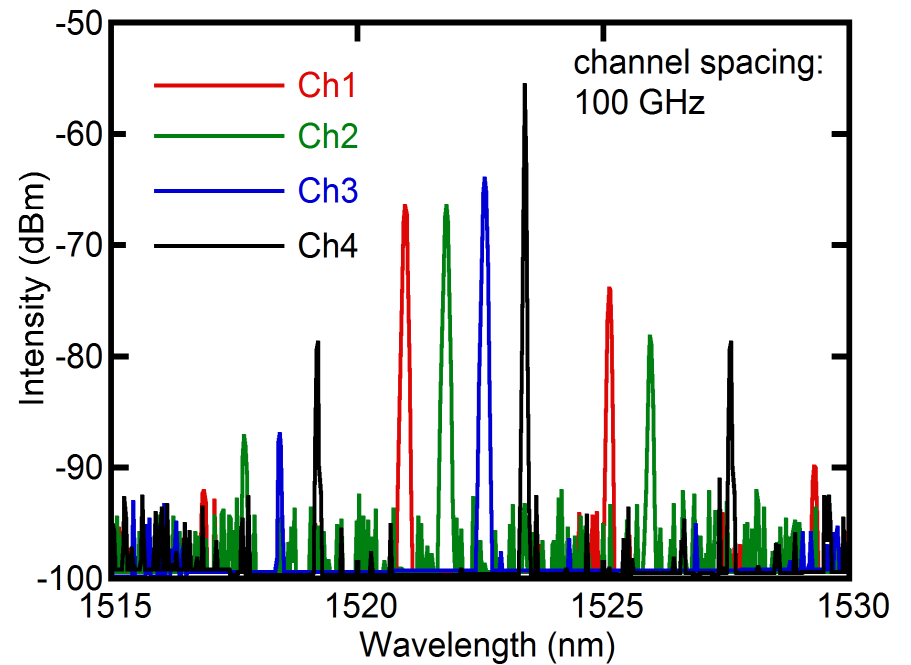
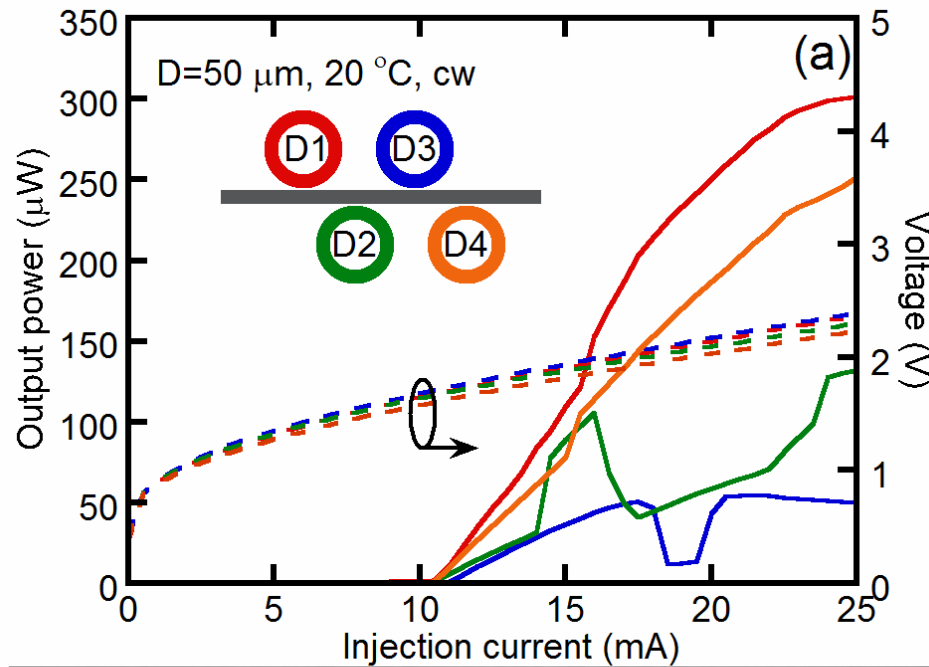
On-chip interconnect



# Device (50 $\mu\text{m}$ ) typical performance



# 4-channel microring laser array



- Lasing wavelength was fine tuned by injection current.

# The Future of Hybrid Silicon Photonics

# Key focus areas:

## 1) Bandwidth/speed

- 25G today moving to 100G
- Also need to be thinking >1Tbps +

## 2) Power

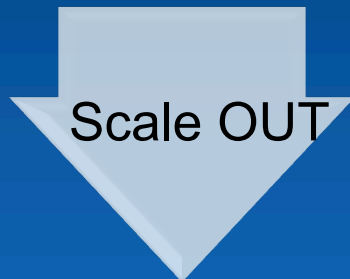
- CMOS voltages scaling below .9V
- How do you drive your devices?
- How do you reduce overall power consumption ?
- Exascale targeting <1mW/Gbps (total I/O)



# The Path to Tera-scale Data Rates

Today: 25 Gbps x 4 = 100Gbps

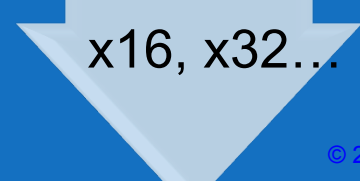
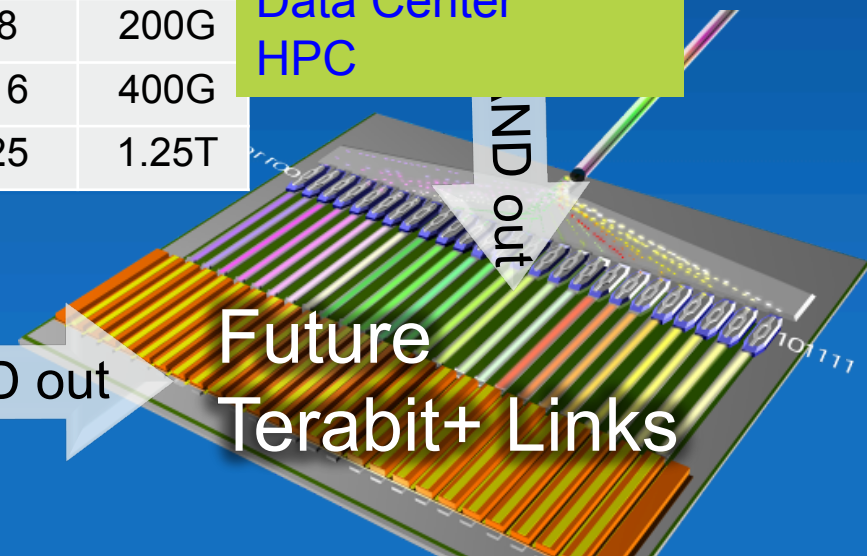
50Gbps x 4 = 200Gbps



Speed	Width	Rate
25	x4	100G
25	x8	200G
25	x16	400G
50	x25	1.25T

Consumer  
Data Center  
HPC

25 Gbps x 8 = 200Gbps

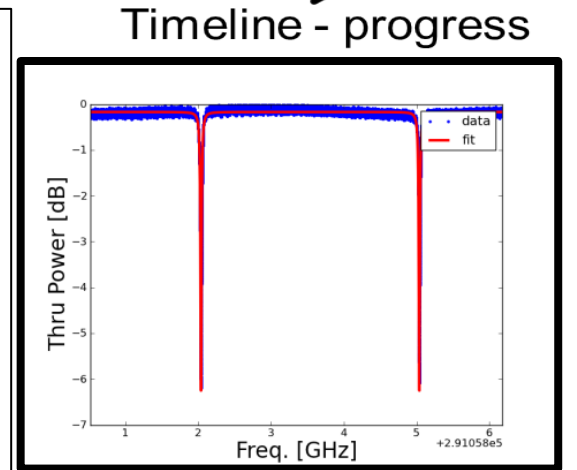
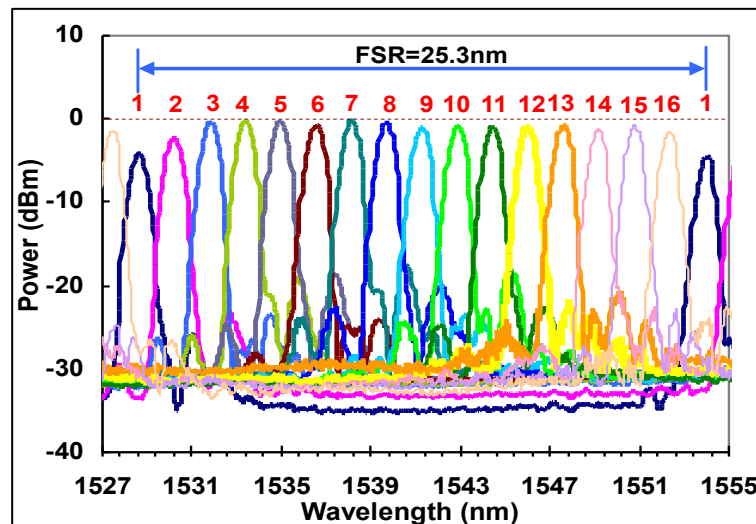
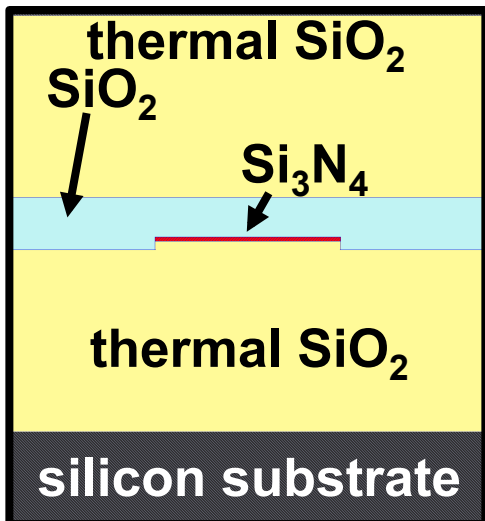
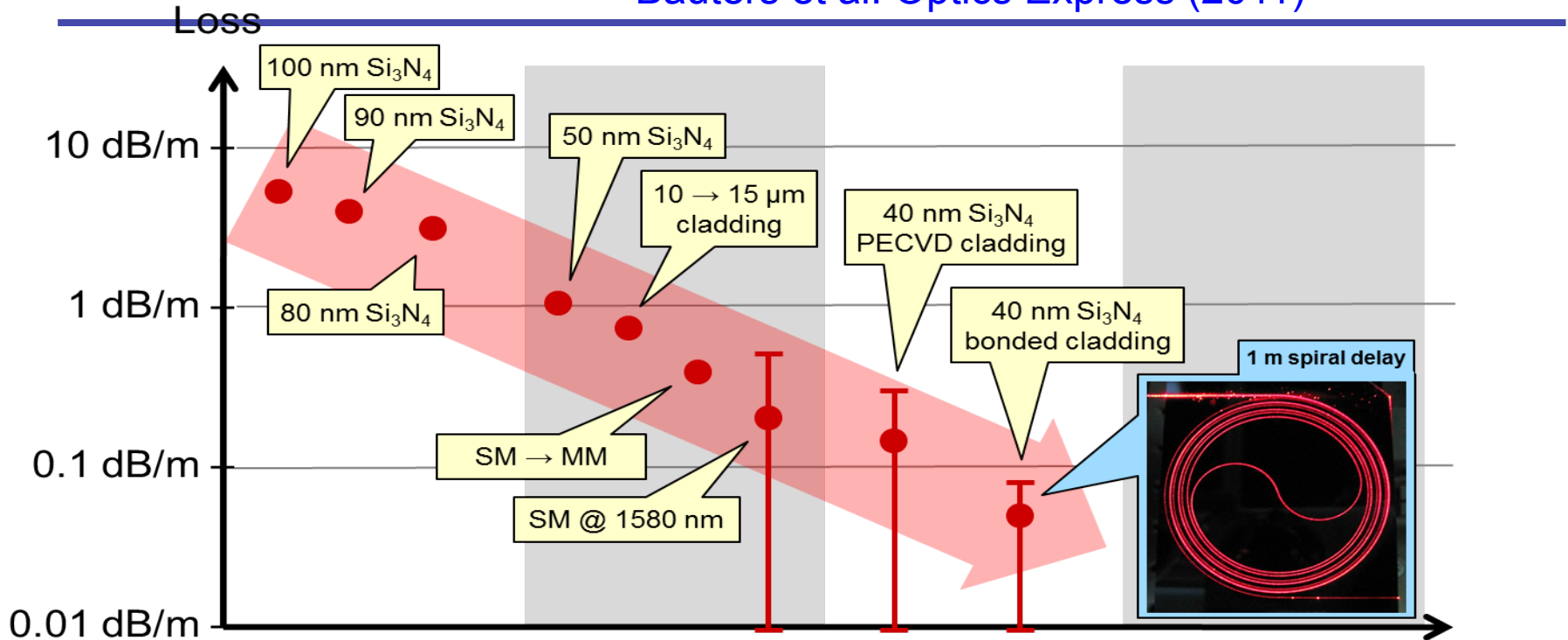


**Low cost integrated photonics allows for Scaling from 50Gbps to >1Tbps**



# Path to Ultralow Loss Waveguides

Bauters et al. Optics Express (2011)



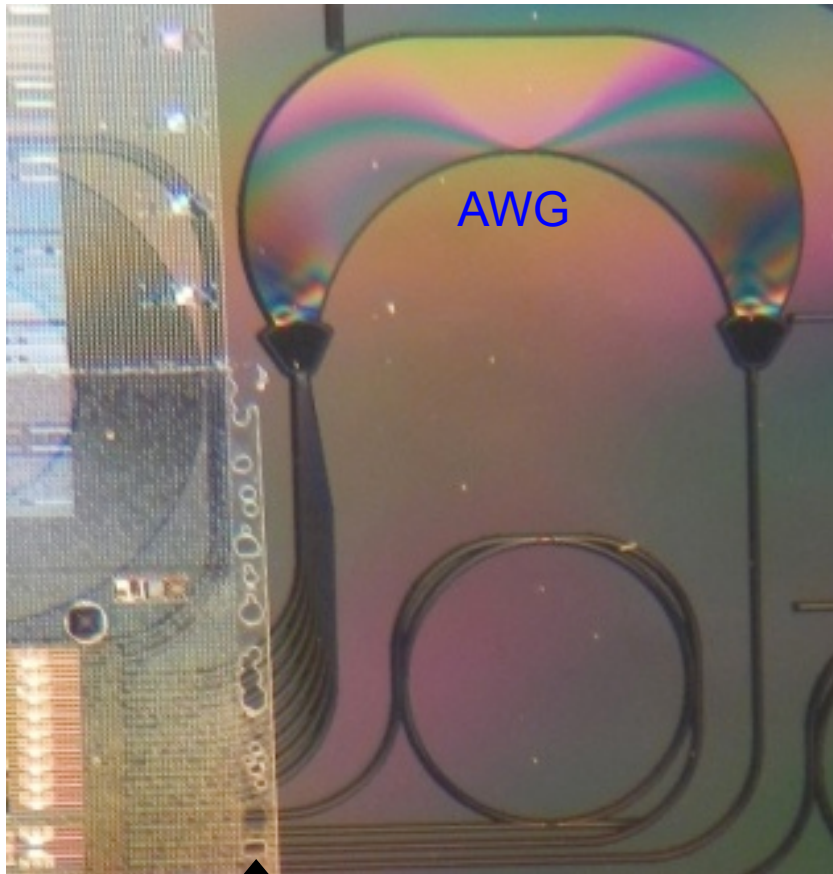
Timeline - progress

High Q Resonators (80Millior)

# UCSB Integration of Ultralow loss waveguides with hybrid silicon: 400 Gbps (8x50 Gbps) Receiver

Davenport et al., OFC Postdeadline (2013)

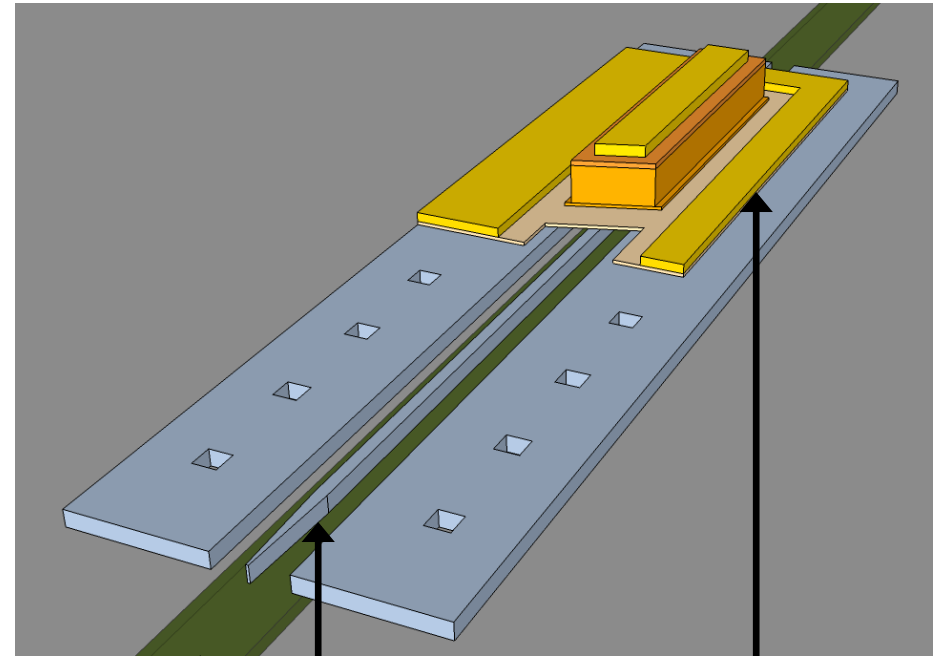
Micrograph of completed device



Detector array

Input waveguide

Detector schematic

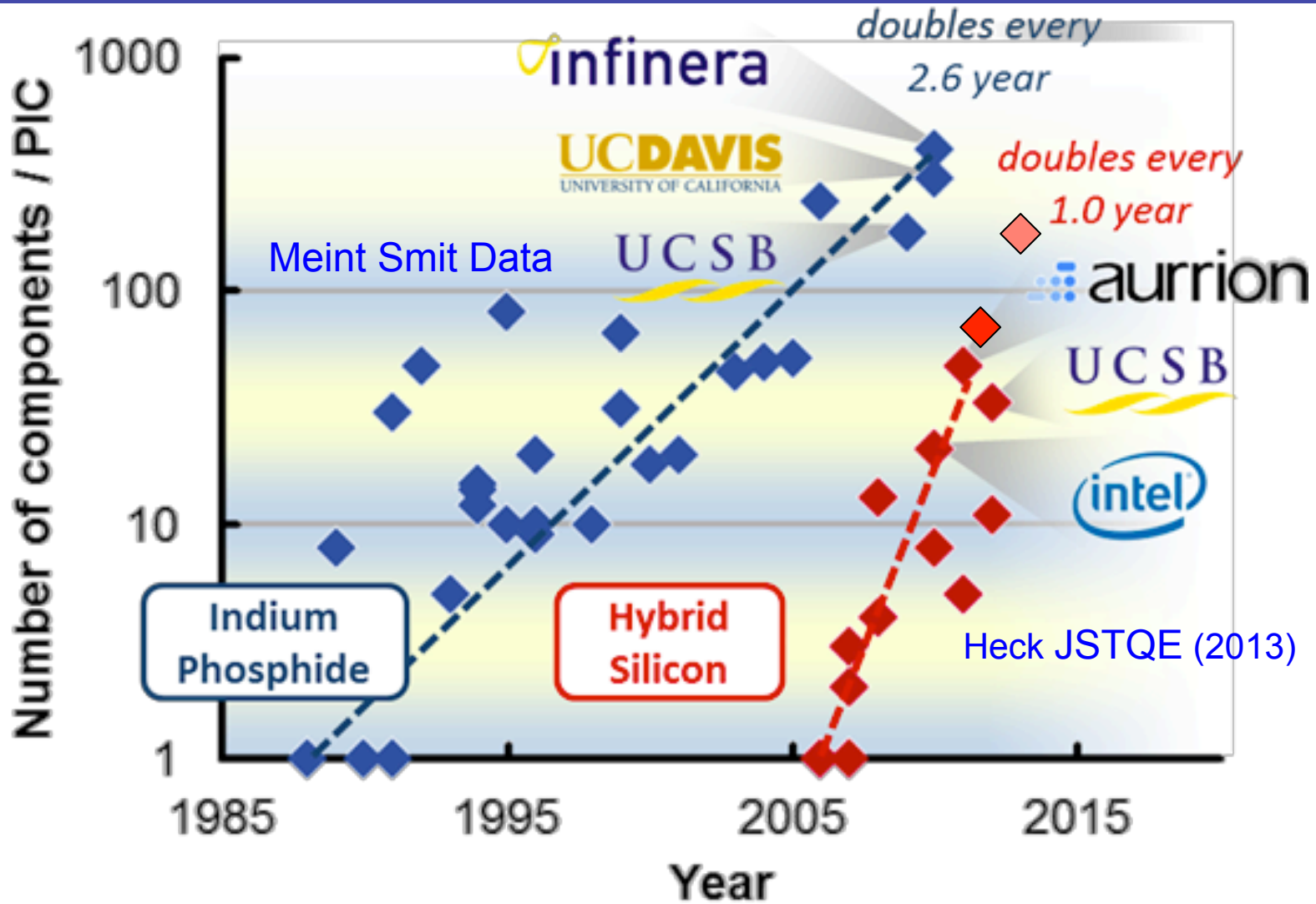


Si3N4 waveguide

Si waveguide and taper

Hybrid Si/InGaAs photodetector

# Photonic Integration





# Hybrid Silicon Record Performance

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- 2013 Narrowest DFB linewidth: **18 kHz** Yariv et al. (Caltech)
- 2011 Lowest waveguide loss on silicon: **0.04 dB/m** Jared Bauters et al.
- 2012 Highest level of integration: **160 devices** Jared Hulme et al.
- 2012 Best reliability: **>40,000 hours at 70C** Srinivasan et al.
- 2012 Highest laser yield: **99%** Srinivasan et al.
- 2012 Fastest Si modulator: **74 GHz** Tang et al.
- 2013 Highest receiver capacity: **400 Gbit/s** Piels et al.
- 2013 Largest laser array bandwidth: **> 200 nm** Jain et al.
- 2014 Largest LED bandwidth: **>200 nm** DeGroote et al.(Ghent and UCSB)
- 2014 Highest temperature: **119C** Alan Liu et al.
- 2014 Highest power: **180 mW** Alan Liu et al.

## UCSB:

**Former students and postdocs:** Alex Fang, Jared Bauters, Hui Wen Chen, Daoxin Dai, Jon Doylend, Martijn Heck, Sid Jain, Geza Kurzveil, Brian Koch, Di Liang, Hyundai Park, Molly Piels, Paolo Pintus, Matt Sysak, Yongbo Tang, Jason Tien

**Present students:** Jock Bovington, Mike Davenport, Jared Hulme, Alan Liu, Jon Peters, Daryl Spencer, Alex Spott, Eric Stanton, Sudha Srinivasan, Chong Zhang

**Colleagues:** Rod Alferness, Dave Auston, Dan Blumenthal, Larry Coldren, Nadir Dagli, Steve Denbaars, Art Gossard, Herb Kroemer, Chris Palmstrom, Mark Rodwell, Adel Saleh, Luke Theogarajan

**Intel :** Richard Jones, Yimin Kang, Mario Paniccia, Matt Sysak

**Aurion:** Alex Fang, Greg Fish, Rob Guzzon, Eric Hall, Brian Koch, Erik Norberg, Anand Ramaswamy, John Roth, Dan Sparacin

**Hewlett Packard:** Di Liang, Geza Kurzveil, Ray Beausoleil

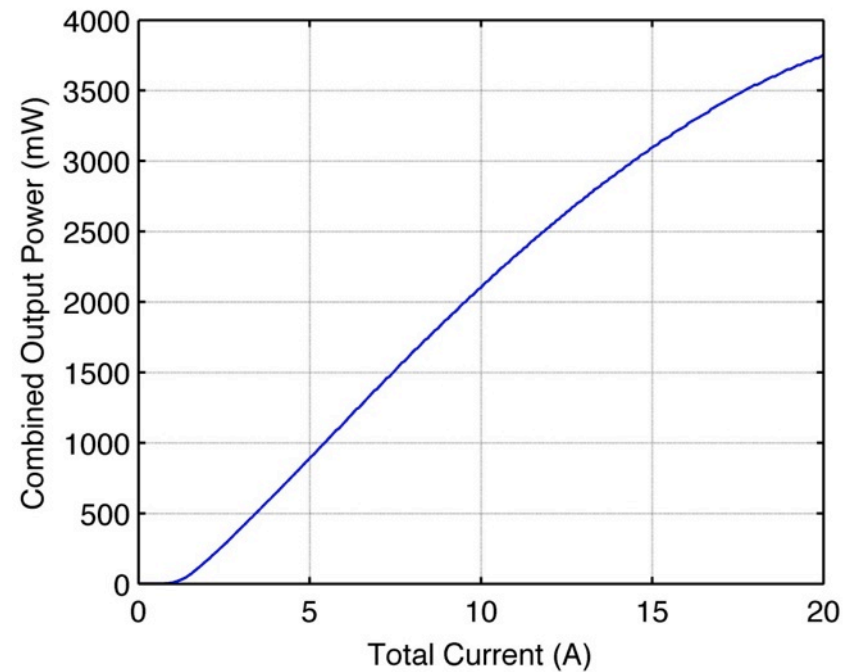
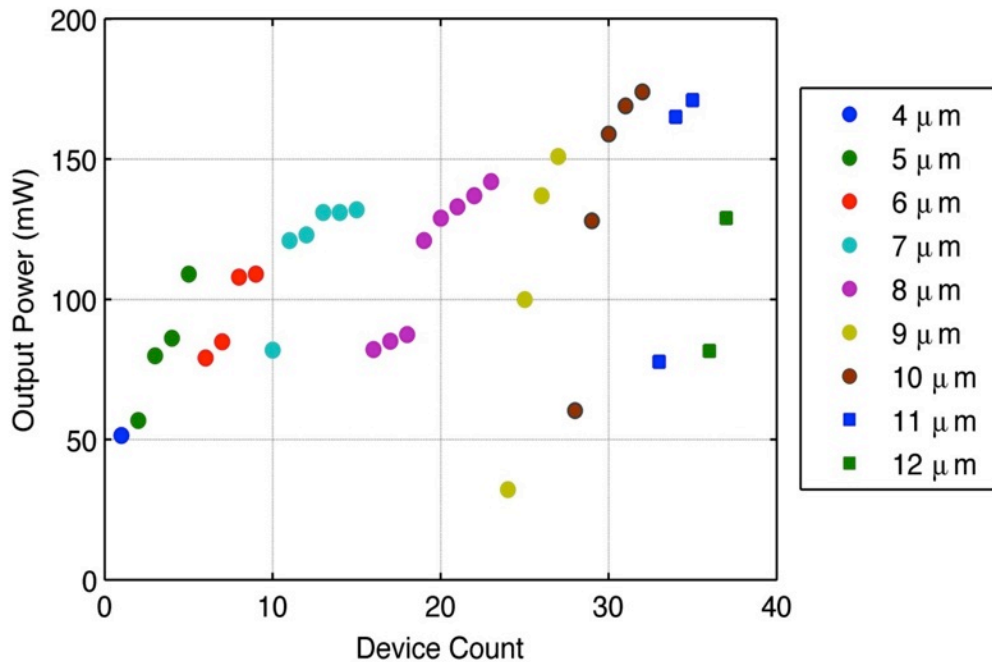
**Slides:** Roel Baets, Tom Koch



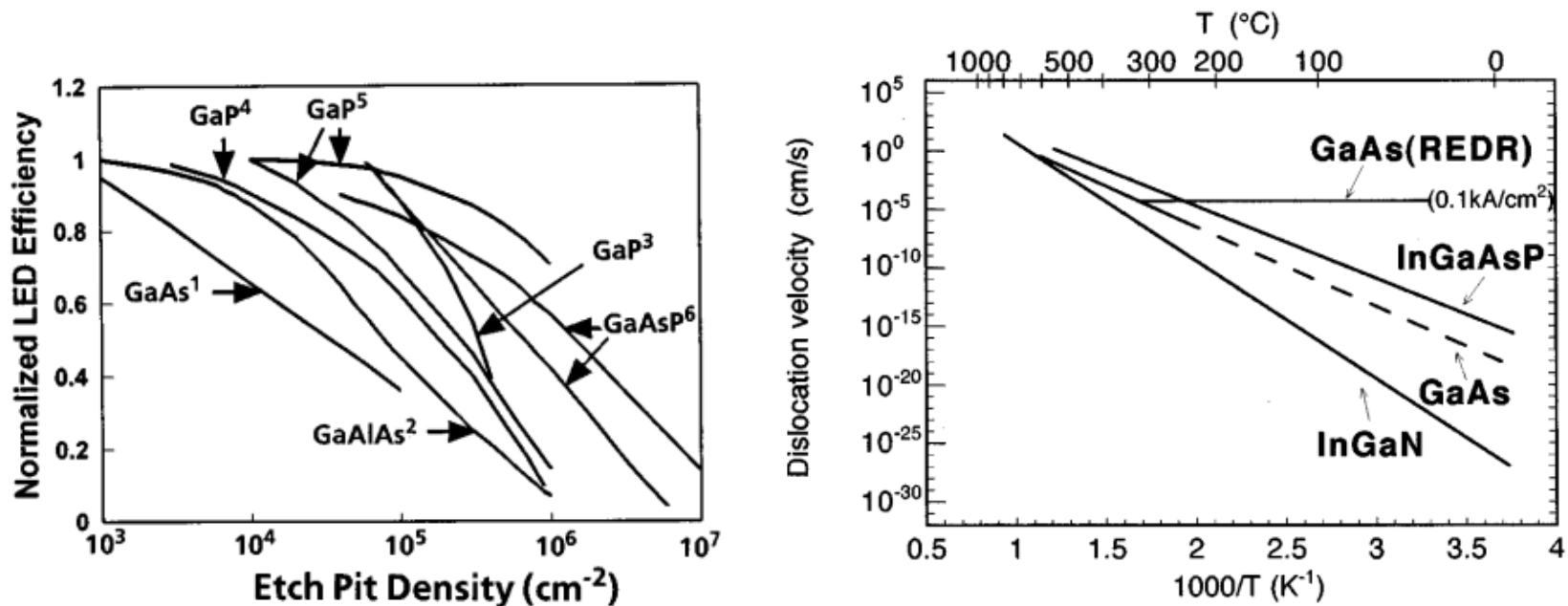
- III-Vs layers on Silicon have key advantages for
  - Low threshold, high power lasers
  - High gain amplifiers
  - High speed modulators
  - Electronics
- Integration is essential for size, weight, power and cost reduction and improved yield and reliability
- Photonics can allow lower power and higher capacity for
  - Sensors
  - Data communication and switching

# Output powers

- Highest yielding laser bar: 37/55 working devices (62%, the rest lost due to facet polishing imperfections and metallization shorts)
- One bar numerically summed (e.g. ignoring thermal cross talk):
  - >3.5 watts of combined CW power at 20 °C.



- GaAs based lasers are very sensitive to defect density and susceptible to failure by recombination enhanced defect reactions (REDR)[1][2]

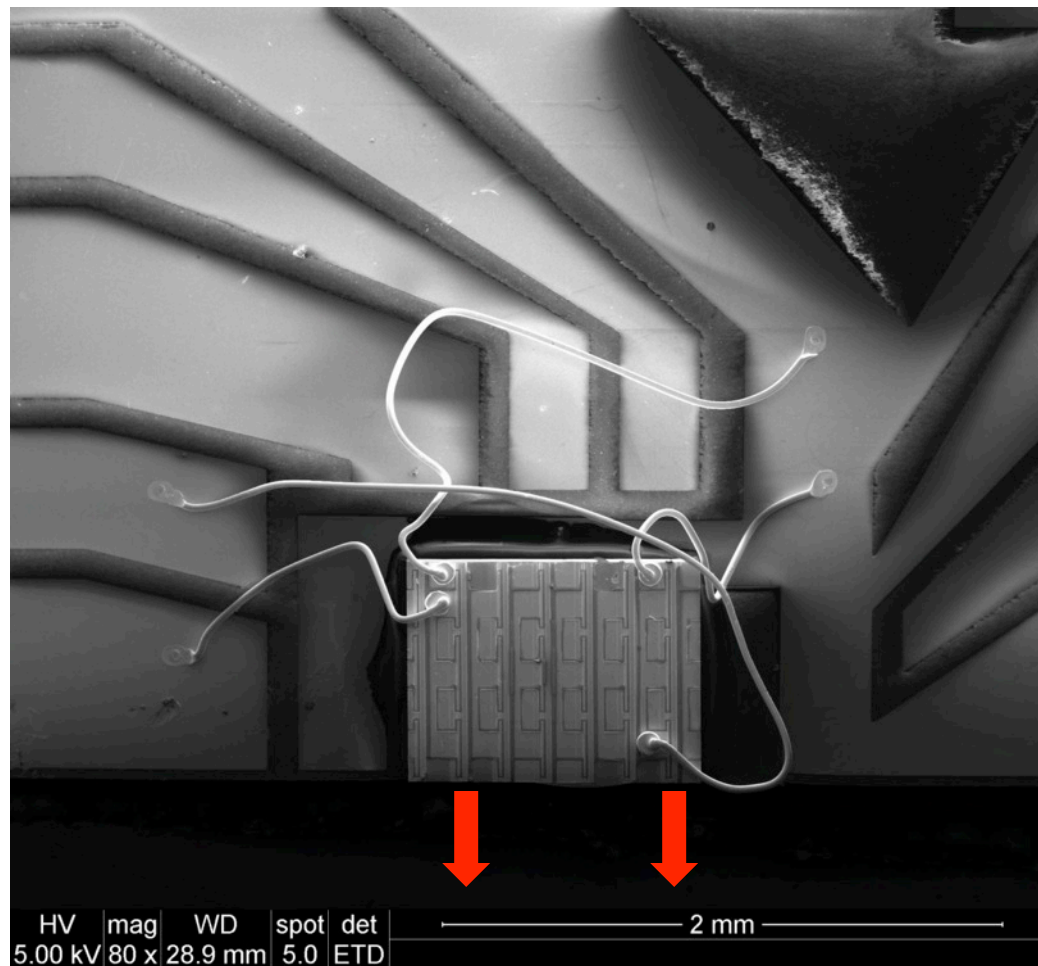


[1] Lester, S. D., et al. "High dislocation densities in high efficiency GaN-based light-emitting diodes." Applied Physics Letters 66.10 (1995): 1249-1251.

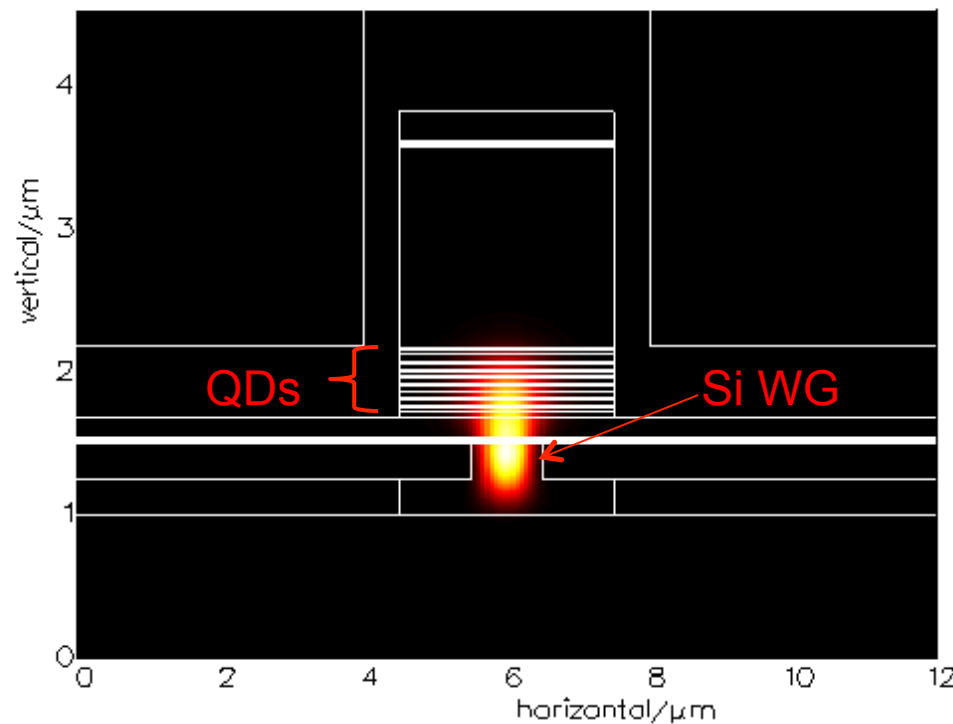
[2] Sugiura, Lisa. "Comparison of degradation caused by dislocation motion in compound semiconductor light-emitting devices." Applied physics letters 70.10 (1997): 1317-1319.



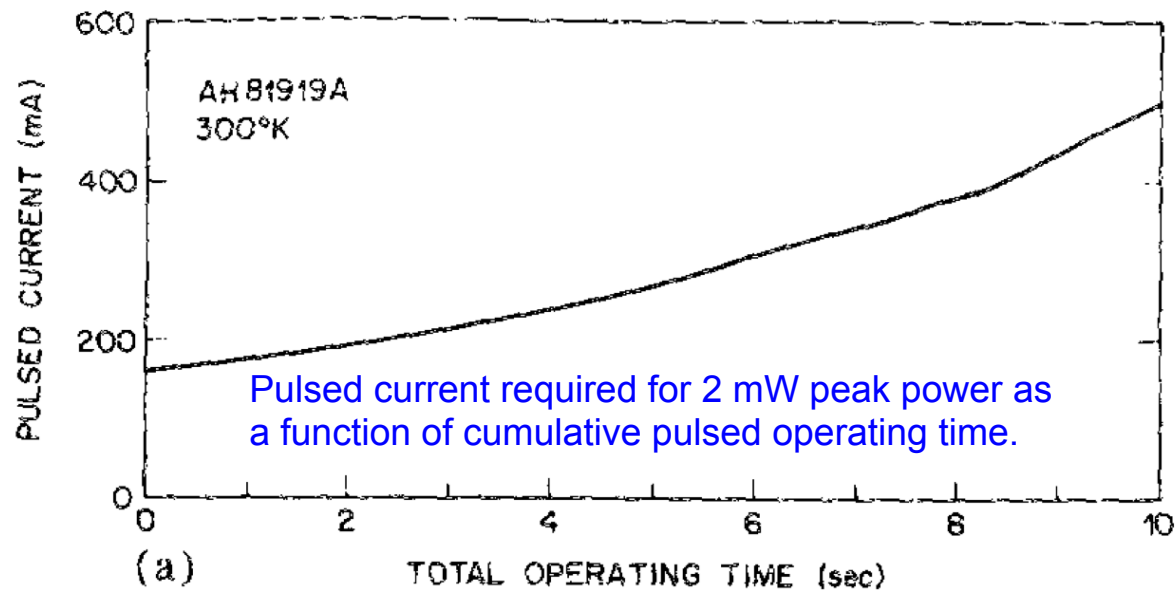
- Stress conditions: 30°C continuous wave under constant 100 mA injection current ( $\sim 1.25\text{-}3\times I_{\text{th}}(0)$ ,  $\sim 1\text{-}20$  mW initial output power)
- Degradation monitored by periodic light-current-voltage (LIV) sweeps at 30 °C



- Repeatably high performance quantum dot lasers on silicon demonstrated
  - Low thresholds (16 mA)
  - CW output power ~180 mW (previous record on silicon: 45 mW)
  - CW lasing up to 120 °C (previous record on silicon: 105 °C)
  - $T_0$  100-200K from 20-40 °C
  - >2100 hours operation under aging at 30°C & 100 mA.
- **Quantum dot lasers are a promising light source for silicon photonics**



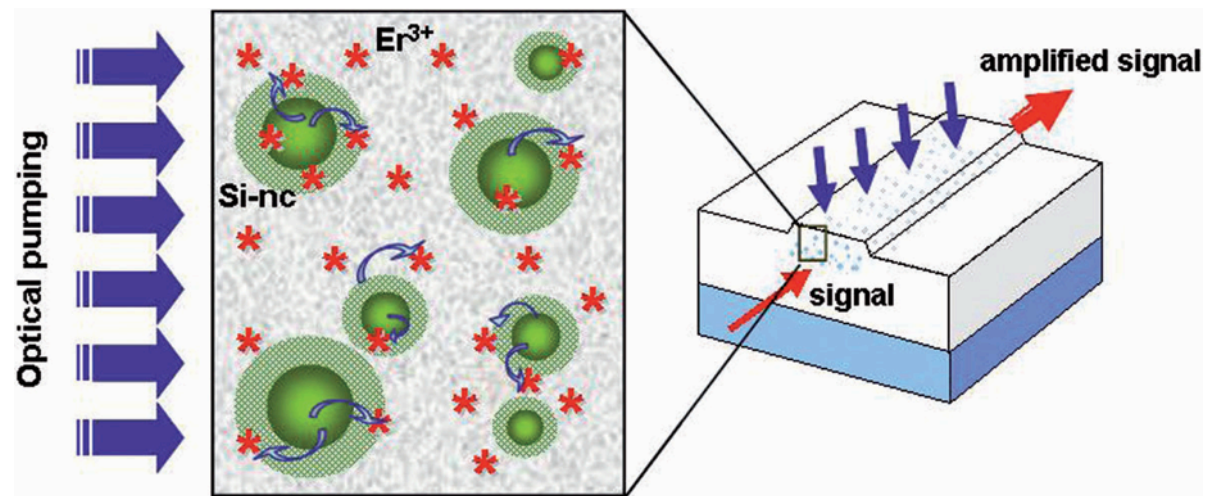
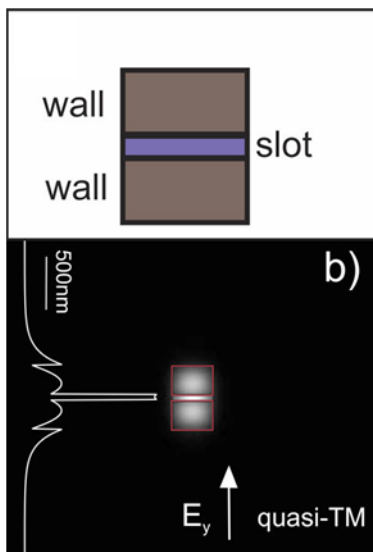
- GaAs based lasers are very sensitive to defect density and susceptible to failure by recombination enhanced defect reactions (REDR)[1][2]
- First GaAs lasers on silicon had lifetimes of **~10 seconds** (RT, pulsed) (1987) [3]



[3] Van der Ziel, J. P., et al. "Degradation of GaAs lasers grown by metalorganic chemical vapor deposition on Si substrates." Appl. Phys. Lett. **51** (1987): 89-91.

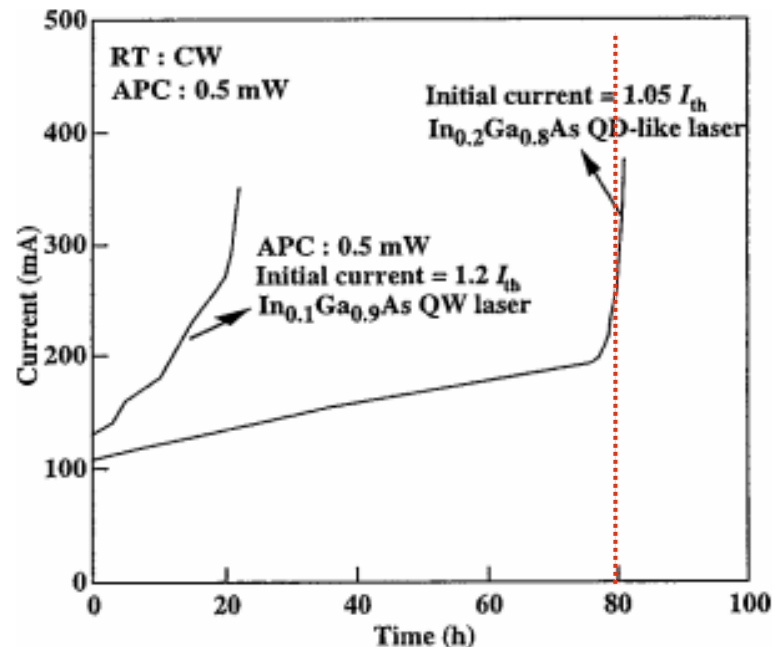
[4] Kazi, Zaman Iqbal, et al. "First Room-Temperature Continuous-Wave Operation of Self-Formed InGaAs Quantum Dot-Like Laser on Si substrate Grown by Metalorganic Chemical Vapor Deposition." Japanese Journal of Applied Physics **39** (2000)

- Si-nc embedded in  $\text{SiO}_2$  can provide optical gain (red wavelengths);
- Slot waveguides provide high  $\text{SiO}_2$  confinement and small cross-section;
- Si-nc creates localization of injected carriers at luminescent centers ( $\text{Er}^{3+}$  for infrared)



*N. Daldosso and L. Pavesi, Laser & Photon. Rev., 2009*

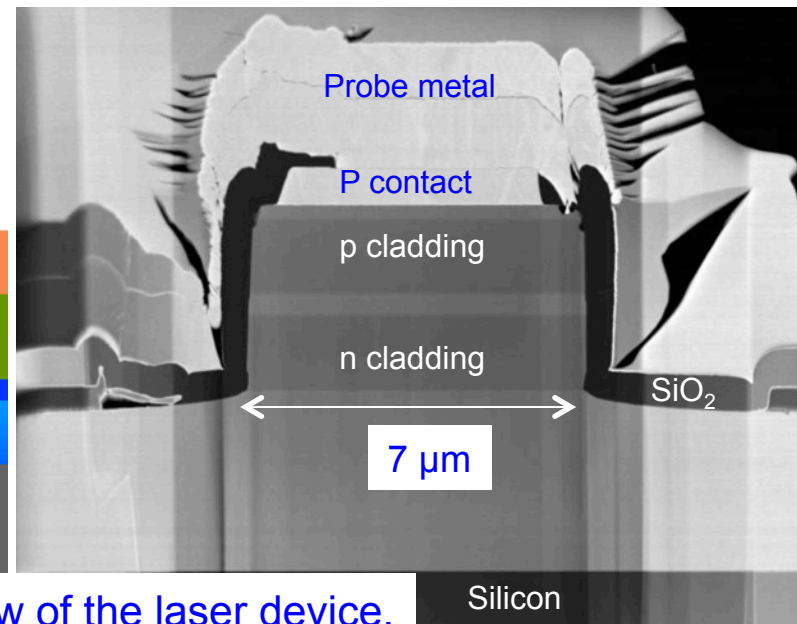
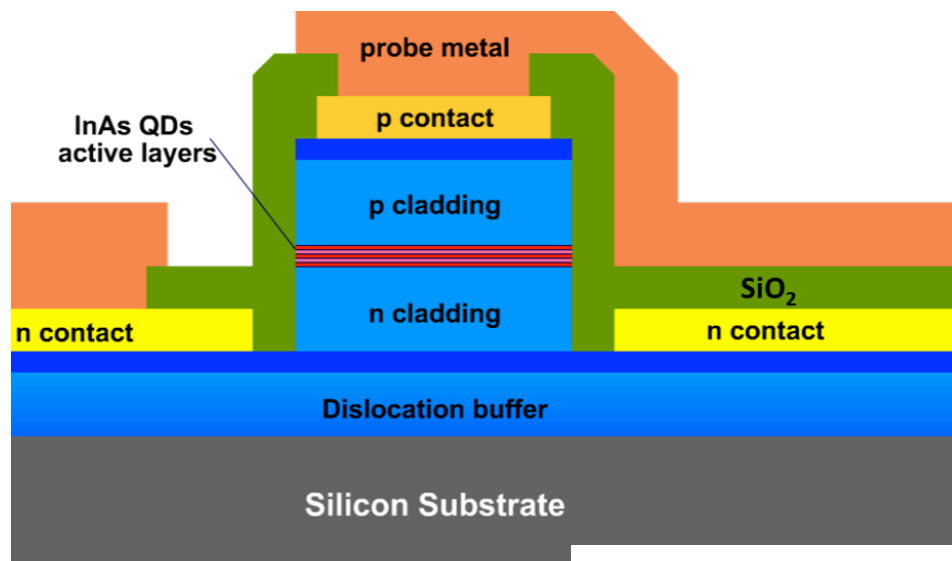
- GaAs based lasers are very sensitive to defect density and susceptible to failure by recombination enhanced defect reactions (REDR)[1][2]
- First GaAs lasers on silicon had lifetimes of ***~10 seconds*** (RT, pulsed) (1987) [3]
- Longest lifetime reported for GaAs based laser on Si (853 nm) is 80 hours (RT, CW) (2000) [4]



[3] Van der Ziel, J. P., et al. "Degradation of GaAs lasers grown by metalorganic chemical vapor deposition on Si substrates." Appl. Phys. Lett. **51** (1987): 89-91.

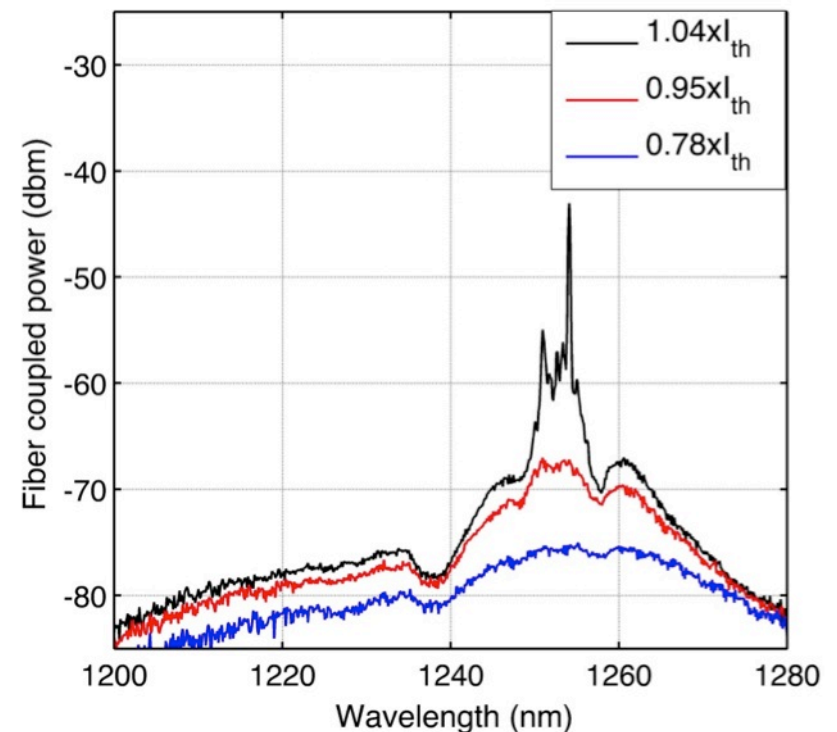
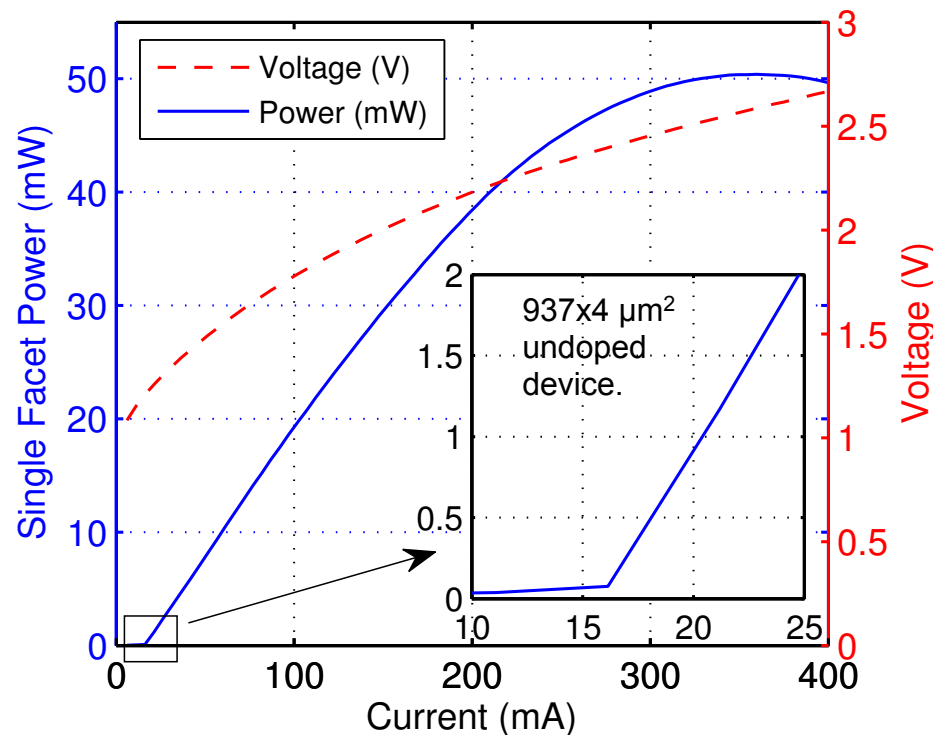
[4] Kazi, Zaman Iqbal, et al. "First Room-Temperature Continuous-Wave Operation of Self-Formed InGaAs Quantum Dot-Like Laser on Si substrate Grown by Metalorganic Chemical Vapor Deposition." Japanese Journal of Applied Physics **39** (2000)

- Epi processed into ridge lasers 4-12  $\mu\text{m}$  wide, 700-1200  $\mu\text{m}$  long cavities.
- Facets were polished, rear facet HR coated ( $\sim 95\%$ ).

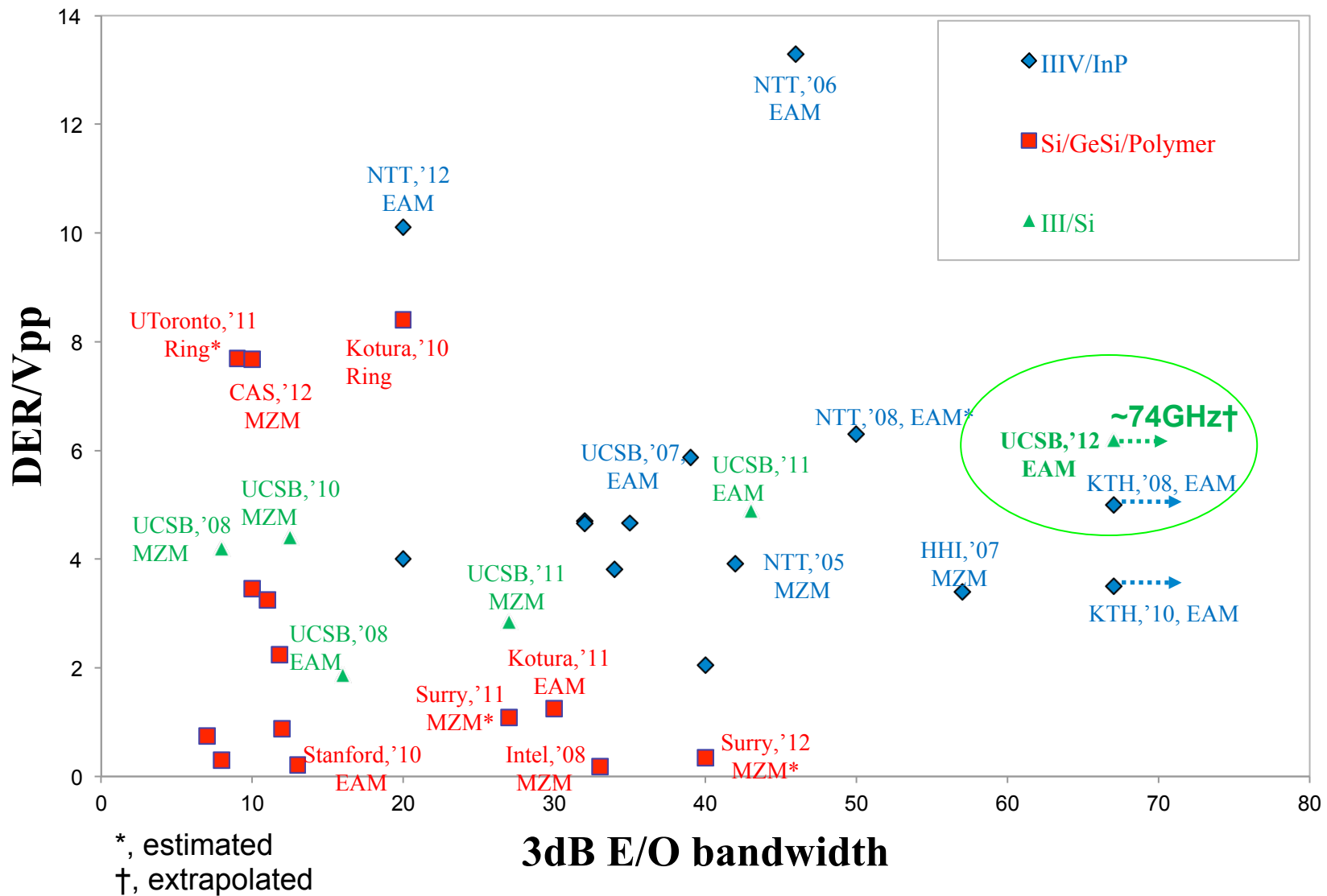


Cross sectional view of the laser device.

- Lowest CW threshold at 20 °C is **16 mA** for an HR coated  $937 \times 4 \mu\text{m}^2$  device with an intrinsic active region (undoped).
- Greater than **50 mW** output power from same device.

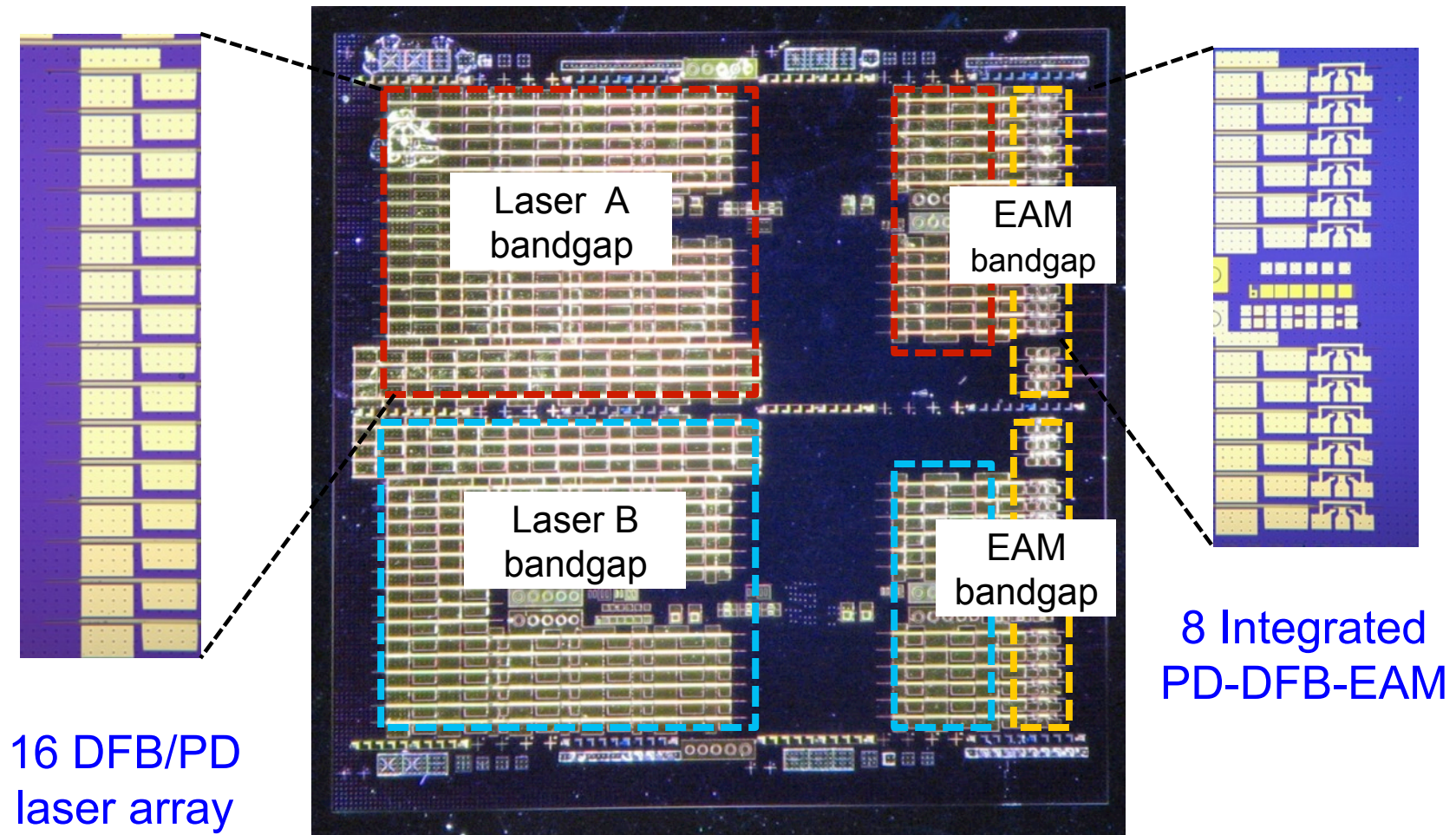


# Modulator Survey

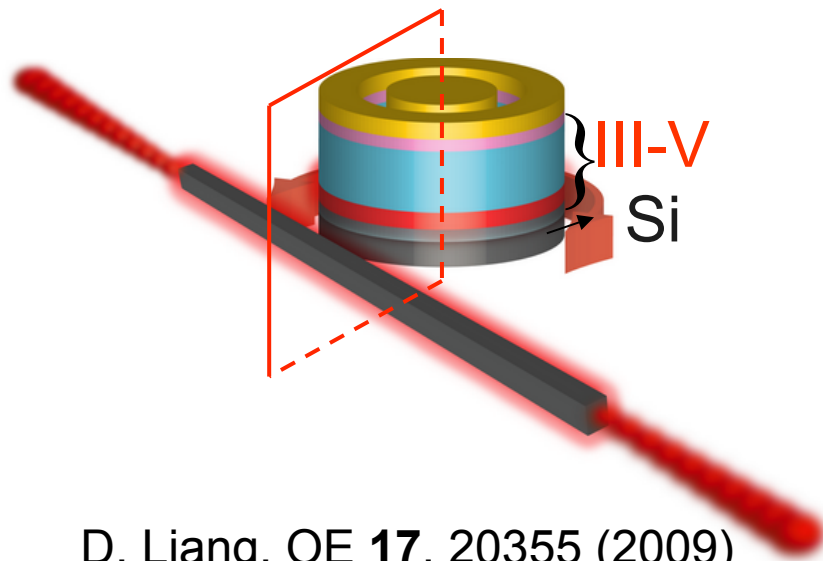




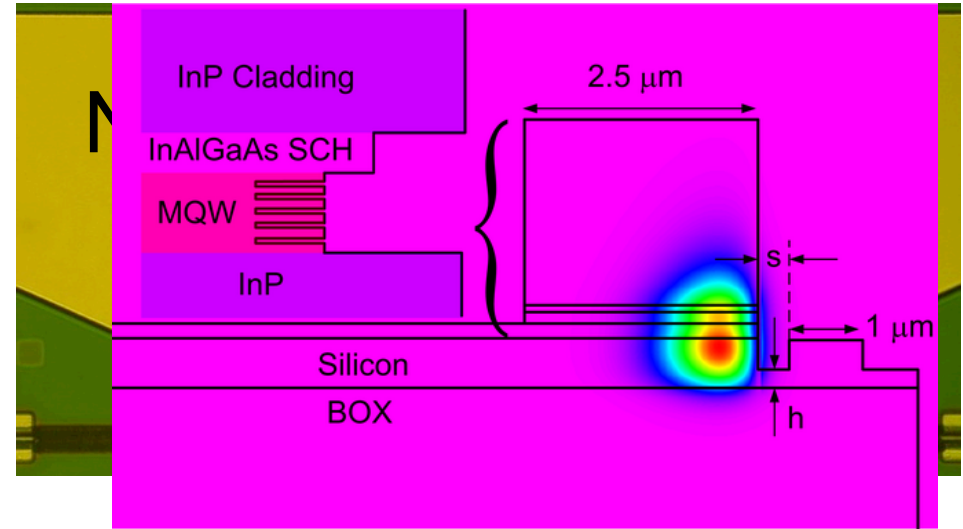
# QWI to Integrate DFBs and EAMs



# Hybrid silicon microring laser



Confinement: MQW: 5.5%; silicon: 52%



D. Liang, OE 17, 20355 (2009)

